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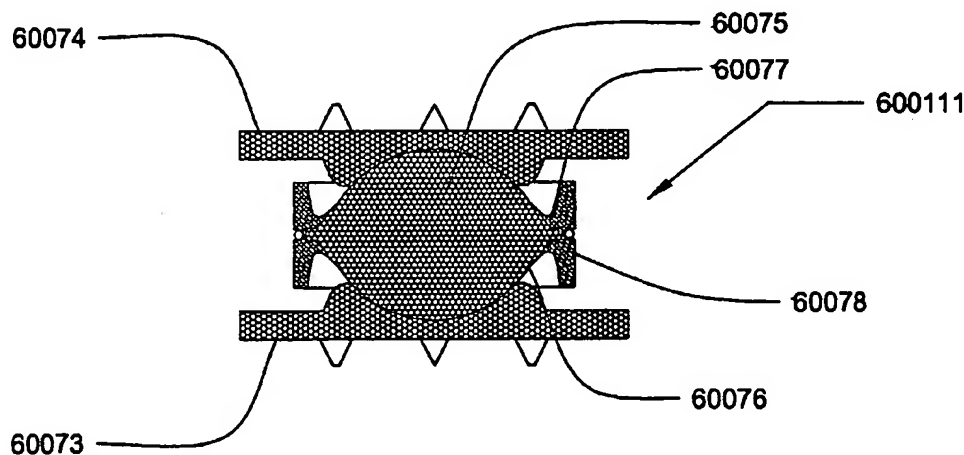
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(54) Title: ARTICULATING DIAMOND-SURFACED SPINAL IMPLANTS



(57) Abstract: An articulating diamond-surfaced spinal implants having a first component (60074) with a concave surface end and a corresponding second element (60075) having a convex surface. The two components form a device with diamond to diamond contact at the articulation point.

## Articulating Diamond-Surfaced Spinal Implants

### CROSS-REFERENCE TO RELATED APPLICATIONS

- 5 Priority is claimed to United States Patent Application Serial No. 10/229,907 filed on August 28, 2002.

### BACKGROUND

- 10 In the past, various spinal implants were known. Most prior art spinal implants were adapted for fusion therapy, although there were some articulating spinal implants as well.

### SUMMARY

- 15 Various articulating diamond-surfaced spinal implants, materials for making them, and methods for making them.

### BRIEF DESCRIPTION OF DRAWINGS

Figures 1A-1BB depict sintering of a polycrystalline diamond compact.

- 20 Figures 1C & 1D depict formation of a diamond table on a substrate by a CVD, PVD or laser deposition method.

Figures 3-12 depict preparation of superhard materials for use in making an articulating diamond-surfaced spinal implant component.

Figures 13-36 depict final preparation of superhard materials prior to sintering.

- 25 Figure 37 depicts the anvils of a cubic press that may be used in making superhard articulating diamond-surfaced spinal implant components.

Figures 38-50 depict machining and finishing superhard articulating diamond-surfaced spinal implant components.

Figures 51 and 52 depict a human spine.

- 30 Figures 53 to 112-3 depict various embodiments of spinal implants.

### DETAILED DESCRIPTION

- 35 Various embodiments of the devices disclosed herein relate to superhard surfaces for articulating diamond-surfaced spinal implants and materials of various compositions, devices of various geometries, attachment mechanisms, methods for making those superhard surfaces for articulating diamond-surfaced spinal implants and components, and products, which include those superhard surfaces for articulating diamond-surfaced spinal implants and components. More specifically,

some embodiments of the devices relate to diamond and sintered polycrystalline diamond surfaces and articulating diamond-surfaced spinal implants that include diamond and polycrystalline diamond surfaces. Some embodiments of the devices utilize a polycrystalline diamond compact ("PDC") to provide a very strong, low friction, long-wearing surface in an articulating diamond-surfaced spinal implant. Any surface, including surfaces outside the field of articulating diamond-surfaced spinal implants, which experience wear and require strength and durability will benefit from advances made here.

There are several design objectives for articulating spinal implants. The implant should maintain height between adjacent vertebrae. It should produce translational stability of the vertebrae. It should provide for intervertebral mobility. And the implant should reproduce disc kinematics. Some embodiments of the spinal implants herein utilize compound bearings and some use non-congruent bearings. One or more of the load bearing and articulation surfaces or contact surfaces of the implant may utilize diamond for smooth and low-friction articulation.

The table below provides a comparison of sintered polycrystalline diamond ("PCD") to some other materials.

TABLE 1

COMPARISON OF SINTERED PCD TO OTHER MATERIALS

Material	Specific Gravity	Hardness (Knoop)	Thermal Conductivity (W/m K)	CTE ( $\times 10^{-6}$ )
Sintered Polycrystalline Diamond Compact	3.5-4.0	9000	900	1.50-4.8
Cubic Boron Nitride	3.48	4500	800	1.0-4.0
Silicon Carbide	3.00	2500	84	4.7-5.3
Aluminum Oxide	3.50	2000		7.8-8.8
Tungsten Carbide (10% Co)	14.6	2200	112	4-6
Cobalt Chrome	8.2	43 RC		16.9
Ti6Al4V	4.43		6.6-17.5	11

Silicon Nitride	3.2	14.2	15-7	1.8-3.7
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In view of the superior hardness of sintered PCD, it is expected that sintered PCD will provide improved wear and durability characteristics.

Reference will now be made to the drawings in which the various elements of the present devices will be discussed. Persons skilled in the design of articulating diamond-surfaced spinal implants and other surfaces will understand the application of the various embodiments of the devices and their principles to articulating diamond-surfaced spinal implants of all types, and components of articulating diamond-surfaced spinal implants, and devices other than those exemplified herein.

As discussed in greater detail below, the articulating diamond-surfaced spinal implant or articulating diamond-surfaced spinal implant component may use polycrystalline diamond compacts in order to form durable load bearing and articulation surfaces. In a polycrystalline diamond compact that includes a substrate, the diamond table may be chemically bonded and/or mechanically fixed to the substrate in a manufacturing process that may use a combination of high pressure and high temperature to form the sintered polycrystalline diamond. Alternatively, free-standing sintered polycrystalline diamond absent a substrate may be formed. Free-standing diamond (without a substrate) may also be referred to as solid diamond. The chemical bonds between diamond and a solvent-catalyst metal are established during the sintering process by combinations of unsatisfied sp<sup>3</sup> carbon bonds with unsatisfied substrate metal bonds. Where a substrate is used, the mechanical bond strength of the diamond table to the substrate that results is a consequence of shape of the substrate and diamond table and differences in the physical properties of the substrate and the diamond table as well as the gradient interface between the substrate and the diamond table. The resulting sintered polycrystalline diamond compact forms a durable articulating diamond-surfaced spinal implant or component.

The diamond table may be polished to a very smooth and glass-like finish to achieve a very low coefficient of friction. The high surface energy of sintered polycrystalline diamond compact causes it to work very well as a load-bearing and articulation surface when a lubricating fluid is present. Its inherent nature allows it to perform very well when a lubricant is absent as well.

While there is discussion herein concerning polycrystalline diamond compacts, the following materials could be considered for forming an articulating spinal implant or component: polycrystalline diamond, monocrystal diamond, natural diamond, diamond created by physical vapor deposition, diamond created by chemical vapor deposition, diamond like carbon, carbonado, cubic boron nitride,



hexagonal boron nitride, or a combination of these, cobalt, chromium, titanium, vanadium, stainless steel, niobium, aluminum, nickel, hafnium, silicon, tungsten, molybdenum, aluminum, zirconium, nitinol, cobalt chrome, cobalt chrome molybdenum, cobalt chrome tungsten, tungsten carbide, titanium carbide, tantalum carbide, zirconium carbide, hafnium carbide, Ti6/4, silicon carbide, chrome carbide, vanadium carbide, yttria stabilized zirconia, magnesia stabilized zirconia, zirconia toughened alumina, titanium molybdenum hafnium, alloys including one or more of the above metals, ceramics, quartz, garnet, sapphire, combinations of these materials, combinations of these and other materials, and other materials may also be used for a desired articulating diamond-surfaced spinal implant or component.

#### SINTERED POLYCRYSTALLINE DIAMOND COMPACTS

One useful material for manufacturing articulating diamond-surfaced spinal implant surfaces, however, is a sintered polycrystalline diamond compact due to its superior performance. Diamond has the greatest hardness and the lowest coefficient of friction of any currently known material. Sintered polycrystalline diamond compacts are chemically inert, are impervious to all solvents, and have the highest thermal conductivity at room temperature of any known material.

In some embodiments of the devices, a polycrystalline diamond compact provides unique chemical bonding and mechanical grip between the diamond and the substrate material.

A method by which PDC may be manufactured is described later in this document. Briefly, it involves sintering diamond crystals to each other, and to a substrate under high pressure and high temperature. Figures 1A and 1B illustrate the physical and chemical processes involved manufacturing polycrystalline diamond compacts.

In Figure 1A, a quantity of diamond feedstock 130 (such as diamond powder or crystals) is placed adjacent to a metal-containing substrate 110 prior to sintering. In the region of the diamond feedstock 130, individual diamond crystals 131 may be seen, and between the individual diamond crystals 131 there are interstitial spaces 132. If desired, a quantity of solvent-catalyst metal may be placed into the interstitial spaces 132. The substrate may also contain solvent-catalyst metal.

The substrate 110 may be a suitable pure metal or alloy, or a cemented carbide containing a suitable metal or alloy as a cementing agent such as cobalt-cemented tungsten carbide. The substrate may be a metal with high tensile strength. In a cobalt-chrome substrate of the devices, the cobalt-chrome alloy will serve as a solvent-catalyst metal for solvating diamond crystals during the sintering process.

The illustration shows the individual diamond crystals and the contiguous metal crystals in the metal substrate. The interface 120 between diamond powder and substrate material is a critical region where bonding of the diamond table to the substrate must occur. In some embodiments of the devices, a boundary layer of a third material different than the diamond and the substrate is placed at the interface 120. This interface boundary layer material, when present, may serve several functions including, but not limited to, enhancing the bond of the diamond table to the substrate, and mitigation of the residual stress field at the diamond-substrate interface.

Once diamond powder or crystals and substrate are assembled as shown in Figure 1A, the assembly is subjected to high pressure and high temperature as described later herein in order to cause bonding of diamond crystals to diamond crystals and to the substrate. The resulting structure of sintered polycrystalline diamond table bonded to a substrate is called a polycrystalline diamond compact (PDC). A compact, as the term is used herein, is a composite structure of two different materials, such as diamond crystals, and a substrate metal. The analogous structure incorporating cubic boron nitride crystals in the sintering process instead of diamond crystals is called polycrystalline cubic boron nitride compact (PCBNC). Many of the processes described herein for the fabrication and finishing of PDC structures and parts work in a similar fashion for PCBNC. In some embodiments of the devices, PCBNC may be substituted for PDC.

Figure 1B depicts a polycrystalline diamond compact 101 after the high pressure and high temperature sintering of diamond feedstock to a substrate. Within the PDC structure, there is an identifiable volume of substrate 102, an identifiable volume of diamond table 103, and a transition zone 104 between diamond table and substrate containing diamond crystals and substrate material. Crystalline grains of substrate material 105 and sintered crystals of diamond 106 are depicted.

On casual examination, the finished compact of Figure 1B will appear to consist of a solid table of diamond 103 attached to the substrate 402 with a discrete boundary. On very close examination, however, a transition zone 104 between diamond table 103 and substrate 102 can be characterized. This zone represents a gradient interface between diamond table and substrate with a gradual transition of ratios between diamond content and metal content. At the substrate side of the transition zone, there will be only a small percentage of diamond crystals and a high percentage of substrate metal, and on the diamond table side, there will be a high percentage of diamond crystals and a low percentage of substrate metal. Because of this gradual transition of ratios of polycrystalline diamond to substrate metal in the transition zone, the diamond table and the substrate have a gradient interface.

In the transition zone or gradient transition zone where diamond crystals and substrate metal are intermingled, chemical bonds are formed between the diamond and metal. From the transition zone 104 into the diamond table 103, the metal content diminishes and is limited to solvent-catalyst metal that fills the three-  
5 dimensional vein-like structure of interstitial voids, openings or asperities 107 within the sintered diamond table structure 103. The solvent-catalyst metal found in the voids or openings 107 may have been swept up from the substrate during sintering or may have been solvent-catalyst metal added to the diamond feedstock before sintering.

10 During the sintering process, there are three types of chemical bonds that are created: diamond-to-diamond bonds, diamond-to-metal bonds, and metal-to-metal bonds. In the diamond table, there are diamond-to-diamond bonds (sp<sup>3</sup> carbon bonds) created when diamond particles partially solvate in the solvate-catalyst metal and then are bonded together. In the substrate and in the diamond table, there are  
15 metal-to-metal bonds created by the high pressure and high temperature sintering process. And in the gradient transition zone, diamond-to-metal bonds are created between diamond and solvent-catalyst metal.

The combination of these various chemical bonds and the mechanical grip exerted by solvent-catalyst metal in the diamond table such as in the interstitial  
20 spaces of the diamond structure diamond table provide extraordinarily high bond strength between the diamond table and the substrate. Interstitial spaces are present in the diamond structure and those spaces typically are filled with solvent-catalyst metal, forming veins of solvent-catalyst metal within the polycrystalline diamond structure. This bonding structure contributes to the extraordinary fracture  
25 toughness of the compact, and the veins of metal within the diamond table act as energy sinks halting propagation of incipient cracks within the diamond structure. The transition zone and metal vein structure provide the compact with a gradient of material properties between those of the diamond table and those of substrate material, further contributing to the extreme toughness of the compact. The transition  
30 zone can also be called an interface, a gradient transition zone, a composition gradient zone, or a composition gradient, depending on its characteristics. The transition zone distributes diamond/substrate stress over the thickness of the zone, reducing zone high stress of a distinct linear interface. The subject residual stress is created as pressure and temperature are reduced at the conclusion of the high  
35 pressure/high temperature sintering process due to the difference in pressure and thermal expansive properties of the diamond and substrate materials.

The diamond sintering process occurs under conditions of extremely high pressure and high temperature. According to the Inventors' best experimental and

theoretical understanding, the diamond sintering process progresses through the following sequence of events. At pressure, a cell containing feedstock of unbonded diamond powder or crystals (diamond feedstock) and a substrate is heated to a temperature above the melting point of the substrate metal 110 and molten metal  
5 flows or sweeps into the interstitial voids 107 between the adjacent diamond crystals 106. It is carried by the pressure gradient to fill the voids as well as being pulled in by the surface energy or capillary action of the large surface area of the diamond crystals 106. As the temperature continues to rise, carbon atoms from the surface of diamond crystals dissolve into this interstitial molten metal, forming a carbon solution.

10 At the proper threshold of temperature and pressure, diamond becomes the thermodynamically favored crystalline allotrope of carbon. As the solution becomes super saturated with respect to  $C_d$  (carbon diamond), carbon from this solution begins to crystallize as diamond onto the surfaces of diamond crystals bonding adjacent diamond crystals together with diamond-diamond bonds into a sintered  
15 polycrystalline diamond structure 106. The interstitial metal fills the remaining void space forming the vein-like lattice structure 107 within the diamond table by capillary forces and pressure driving forces. Because of the crucial role that the interstitial metal plays in forming a solution of carbon atoms and stabilizing these reactive atoms during the diamond crystallization phase in which the polycrystalline diamond structure is formed, the metal is referred to as a solvent-catalyst metal.  
20

Figure 1BB depicts a sintered polycrystalline diamond compact having both substrate metal 180 and diamond 181, but in which there is a continuous gradient transition 182 from substrate metal to diamond. In such a compact, the gradient transition zone may be the entire compact, or a portion of the compact. The  
25 substrate side of the compact may contain nearly pure metal for easy machining and attachment to other components, while the diamond side may be extremely hard, smooth and durable for use in a hostile work environment.

In some embodiments of the devices, a quantity of solvent-catalyst metal may be combined with the diamond feedstock prior to sintering. This is found to be useful  
30 when forming thick PCD tables, solid PDC structures, or when using multimodal fine diamond where there is little residual free space within the diamond powder. In each of these cases, there may not be sufficient ingress of solvent-catalyst metal via the sweep mechanism to adequately mediate the sintering process as a solvent-catalyst. The metal may be added by direct addition of powder, or by generation of metal  
35 powder in situ with an attritor mill or by the well-known method of chemical reduction of metal salts deposited on diamond crystals. Added metal may constitute any amount from less than 1% by mass, to greater than 35%. This added metal may consist of the same metal or alloy as is found in the substrate, or may be a different

metal or alloy selected because of its material and mechanical properties. Example ratios of diamond feedstock to solvent-catalyst metal prior to sintering include mass ratios of 70:30, 85:15, 90:10, and 95:15. The metal in the diamond feedstock may be added powder metal, metal added by an attritor method, vapor deposition or  
5 chemical reduction of metal into powder.

When sintering diamond on a substrate with an interface boundary layer, it may be that no solvent-catalyst metal from the substrate is available to sweep into the diamond table and participate in the sintering process. In this case, the boundary layer material, if composed of a suitable material, metal or alloy that can function as a  
10 solvent-catalyst, may serve as the sweep material mediating the diamond sintering process. In other cases where the desired boundary material cannot serve as a solvent-catalyst, a suitable amount of solvent-catalyst metal powder as described herein is added to the diamond crystal feed stock as described above. This assembly is then taken through the sintering process. In the absence of a substrate  
15 metal source, the solvent-catalyst metal for the diamond sintering process must be supplied entirely from the added metal powder. The boundary material may bond chemically to the substrate material, and bonds chemically to the diamond table and/or the added solvent-catalyst metal in the diamond table. The remainder of the sintering and fabrication process may be the same as with the conventional solvent-catalyst sweep sintering and fabrication process.  
20

For the sake of simplicity and clarity in this patent, the substrate, transition zone, and diamond table have been discussed as distinct layers. However, it is important to realize that the finished sintered object may be a composite structure characterized by a continuous gradient transition from substrate material to diamond  
25 table rather than as distinct layers with clear and discrete boundaries, hence the term "compact".

In addition to the sintering processes described above, diamond parts suitable for use as articulating diamond-surfaced spinal implants components may also be fabricated as solid or free-standing polycrystalline diamond structures without  
30 a substrate. These may be formed by placing the diamond powder combined with a suitable amount of added solvent-catalyst metal powder as described above in a refractory metal can (typically Ta, Nb, Zr, or Mo) with a shape approximating the shape of the final part desired. This assembly is then taken through the sintering process. However, in the absence of a substrate metal source, the solvent-catalyst  
35 metal for the diamond sintering process must be supplied entirely from the added metal powder. With suitable finishing, objects thus formed may be used as is, or bonded to metal or other substrates.

Sintering is a method of creating a diamond table with a strong and durable constitution. Other methods of producing a diamond table that may or may not be bonded to a substrate are possible. At present, these typically are not as strong or durable as those fabricated with the sintering process. It is also possible to use  
5 these methods to form diamond structures directly onto substrates suitable for use as articulating diamond-surfaced spinal implants. A table of polycrystalline diamond either with or without a substrate may be manufactured and later attached to an articulating diamond-surfaced spinal implant in a location such that it will form a surface. The attachment could be performed with any suitable method, including  
10 welding, brazing, sintering, diffusion welding, diffusion bonding, inertial welding, adhesive bonding, or the use of fasteners such as screws, bolts, or rivets. In the case of attaching a diamond table without a substrate to another object, the use of such methods as brazing, diffusion welding/bonding or inertia welding may be most appropriate.

15 Although high pressure/high temperature sintering is a method for creating a diamond surface, other methods for producing a volume of diamond may be employed as well. For example, either chemical vapor deposition (CVD), or physical vapor deposition (PVD) processes may be used. CVD produces a diamond layer by thermally cracking an organic molecule and depositing carbon radicals on a  
20 substrate. PVD produces a diamond layer by electrically causing carbon radicals to be ejected from a source material and to deposit on a substrate where they build a diamond crystal structure.

The CVD and PVD processes have some advantages over sintering. Sintering is performed in large, expensive presses at high pressure (such as 45-68  
25 kilobars) and at high temperatures (such as 1200 to 1500 degrees Celsius). It is difficult to achieve and maintain desired component shape using a sintering process because of flow of high pressure mediums used and possible deformation of substrate materials.

In contrast, CVD and PVD take place at atmospheric pressure or lower, so  
30 there no need for a pressure medium and there is no deformation of substrates.

Another disadvantage of sintering is that it is difficult to achieve some geometries in a sintered polycrystalline diamond compact. When CVD or PVD are used, however, the gas phase used for carbon radical deposition can completely conform to the shape of the object being coated, making it easy to achieve a desired  
35 non-planar shape.

Another potential disadvantage of sintering polycrystalline diamond compacts is that the finished component will tend to have large residual stresses caused by differences in the coefficient of thermal expansion and modulus between the

diamond and the substrate. While residual stresses can be used to improve strength of a part, they can also be disadvantageous. When CVD or PVD is used, residual stresses can be minimized because CVD and PVD processes do not involve a significant pressure transition (such from 68 Kbar to atmospheric pressure in high pressure and high temperature sintering) during manufacturing.

Another potential disadvantage of sintering polycrystalline diamond compacts is that few substrates have been found that are suitable for sintering. Tungsten carbide is a common choice for substrate materials. When CVD or PVD are used, however, synthetic diamond can be placed on many substrates, including titanium, most carbides, silicon, molybdenum and others. This is because the temperature and pressure of the CVD and PVD coating processes are low enough that differences in coefficient of thermal expansion and modulus between diamond and the substrate are not as critical as they are in a high temperature and high pressure sintering process.

A further difficulty in manufacturing sintered polycrystalline diamond compacts is that as the size of the part to be manufactured increases, the size of the press must increase as well. Sintering of diamond will only take place at certain pressures and temperatures, such as those described herein. In order to manufacture larger sintered polycrystalline diamond compacts, ram pressure of the press (tonnage) and size of tooling (such as dies and anvils) must be increased in order to achieve the necessary pressure for sintering to take place. But increasing the size and capacity of a press is more difficult than simply increasing the dimensions of its components. There may be a practical physical size constraints on press size due to the manufacturing process used to produce press tooling.

Tooling for a press is typically made from cemented tungsten carbide. In order to make tooling, the cemented tungsten carbide is sintered in a vacuum furnace followed by pressing in a hot isostatic press ("HIP") apparatus. Hipping must be performed in a manner that maintains uniform temperature throughout the tungsten carbide in order to achieve uniform physical qualities and quality. These requirements impose a practical limit on the size tooling that can be produced for a press that is useful for sintering polycrystalline diamond compacts. The limit on the size tooling that can be produced also limits the size press that can be produced.

CVD and PVD manufacturing apparatuses may be scaled up in size with few limitations, allowing them to produce polycrystalline diamond compacts of almost any desired size.

CVD and PVD processes are also advantageous because they permit precise control of the thickness and uniformity of the diamond coating to be applied to a substrate. Temperature is adjusted within the range of 500 to 1000 degrees Celsius,

and pressure is adjusted in a range of less than 1 atmosphere to achieve desired diamond coating thickness.

Another advantage of CVD and PVD processes is that they allow the manufacturing process to be monitored as it progresses. A CVD or PVD reactor can be opened before manufacture of a part is completed so that the thickness and quality of the diamond coating being applied to the part may be determined. From the thickness of the diamond coating that has already been applied, time to completion of manufacture can be calculated. Alternatively, if the coating is not of desired quality, the manufacturing processes may be aborted in order to save time and money.

In contrast, sintering of polycrystalline diamond compacts is performed as a batch process that cannot be interrupted, and progress of sintering cannot be monitored. The pressing process must be run to completion and the part may only be examined afterward.

15

#### CVD AND PVD DIAMOND

CVD is performed in an apparatus called a reactor. A basic CVD reactor includes four components. The first component of the reactor is one or more gas inlets. Gas inlets may be chosen based on whether gases are premixed before introduction to the chamber or whether the gases are allowed to mix for the first time in the chamber. The second component of the reactor is one or more power sources for the generation of thermal energy. A power source is needed to heat the gases in the chamber. A second power source may be used to heat the substrate material uniformly in order to achieve a uniform coating of diamond on the substrate. The third component of the reactor is a stage or platform on which a substrate is placed. The substrate will be coated with diamond during the CVD process. Stages used include a fixed stage, a translating stage, a rotating stage and a vibratory stage. An appropriate stage must be chosen to achieved desired diamond coating quality and uniformity. The fourth component of the reactor is an exit port for removing exhaust gas from the chamber. After gas has reacted with the substrate, it must be removed from the chamber as quickly as possible so that it does not participate in other reactions, which would be deleterious to the diamond coating.

CVD reactors are classified according to the power source used. The power source is chosen to create the desired species necessary to carry out diamond thin film deposition. Some CVD reactor types include plasma-assisted microwave, hot filament, electron beam, single, double or multiple laser beam, arc jet and DC discharge. These reactors differ in the way they impart thermal energy to the gas species and in their efficiency in breaking gases down to the species necessary for



deposition of diamond. It is possible to have an array of lasers to perform local heating inside a high pressure cell. Alternatively, an array of optical fibers could be used to deliver light into the cell.

The basic process by which CVD reactors work is as follows. A substrate is placed into the reactor chamber. Reactants are introduced to the chamber via one or more gas inlets. For diamond CVD, methane ( $\text{CH}_4$ ) and hydrogen ( $\text{H}_2$ ) gases may be brought into the chamber in premixed form. Instead of methane, any carbon-bearing gas in which the carbon has  $\text{sp}^3$  bonding may be used. Other gases may be added to the gas stream in order to control quality of the diamond film, deposition temperature, grain structure and growth rate. These include oxygen, carbon dioxide, argon, halogens and others.

The gas pressure in the chamber may be maintained at about 100 torr. Flow rates for the gases through the chamber may be about 10 standard cubic centimeters per minute for methane and about 100 standard cubic centimeters per minute for hydrogen. The composition of the gas phase in the chamber may be in the range of 90-99.5% hydrogen and 0.5-10% methane.

When the gases are introduced into the chamber, they are heated. Heating may be accomplished by many methods. In a plasma-assisted process, the gases are heated by passing them through a plasma. Otherwise, the gases may be passed over a series of wires such as those found in a hot filament reactor.

Heating the methane and hydrogen will break them down into various free radicals. Through a complicated mixture of reactions, carbon is deposited on the substrate and joins with other carbon to form crystalline diamond by  $\text{sp}^3$  bonding. The atomic hydrogen in the chamber reacts with and removes hydrogen atoms from methyl radicals attached to the substrate surface in order to create molecular hydrogen, leaving a clear solid surface for further deposition of free radicals.

If the substrate surface promotes the formation of  $\text{sp}^2$  carbon bonds, or if the gas composition, flow rates, substrate temperature or other variables are incorrect, then graphite rather than diamond will grow on the substrate.

There are many similarities between CVD reactors and processes and PVD reactors and processes. PVD reactors differ from CVD reactors in the way that they generate the deposition species and in the physical characteristics of the deposition species. In a PVD reactor, a plate of source material is used as a thermal source, rather than having a separate thermal source as in CVD reactors. A PVD reactor generates electrical bias across a plate of source material in order to generate and eject carbon radicals from the source material. The reactor bombards the source material with high energy ions. When the high energy ions collide with source material, they cause ejection of the desired carbon radicals from the source material.

The carbon radicals are ejected radially from the source material into the chamber. The carbon radicals then deposit themselves onto whatever is in their path, including the stage, the reactor itself, and the substrate.

Referring to Figure 1C, a substrate 140 of appropriate material is depicted having a deposition face 141 on which diamond may be deposited by a CVD or PVD process. Figure 1D depicts the substrate 140 and the deposition face 141 on which a volume of diamond 142 has been deposited by CVD or PVD processes. A small transition zone 143 is present in which both diamond and substrate are located. In comparison to Figure 1B, it can be seen that the CVD or PVD diamond deposited on a substrate lacks the more extensive gradient transition zone of sintered polycrystalline diamond compacts because there is no sweep of solvent-catalyst metal through the diamond table in a CVD or PVD process.

Both CVD and PVD processes achieve diamond deposition by line of sight. Means (such as vibration and rotation) are provided for exposing all desired surfaces for diamond deposition. If a vibratory stage is to be used, the surface will vibrate up and down with the stage and thereby present all surfaces to the free radical source.

There are several methods, which may be implemented in order to coat cylindrical objects with diamond using CVD or PVD processes. If a plasma assisted microwave process is to be used to achieve diamond deposition, then the object to receive the diamond must be directly under the plasma in order to achieve the highest quality and most uniform coating of diamond. A rotating or translational stage may be used to present every aspect of the surface to the plasma for diamond coating. As the stage rotates or translates, all portions of the surface may be brought directly under the plasma for coating in such a way to achieve sufficiently uniform coating.

If a hot filament CVD process is used, then the surface should be placed on a stationary stage. Wires or filaments (typically tungsten) are strung over the stage so that their coverage includes the surface to be coated. The distance between the filaments and the surface and the distance between the filaments themselves may be chosen to achieve a uniform coating of diamond directly under the filaments.

Diamond surfaces can be manufactured by CVD and PVD process either by coating a substrate with diamond or by creating a free standing volume of diamond, which is later mounted for use. A free standing volume of diamond may be created by CVD and PVD processes in a two-step operation. First, a thick film of diamond is deposited on a suitable substrate, such as silicon, molybdenum, tungsten or others. Second, the diamond film is released from the substrate.

As desired, segments of diamond film may be cut away, such as by use of a Q-switched YAG laser. Although diamond is transparent to a YAG laser, there is

usually a sufficient amount of  $sp^2$  bonded carbon (as found in graphite) to allow cutting to take place. If not, then a line may be drawn on the diamond film using a carbon-based ink. The line should be sufficient to permit cutting to start, and once started, cutting will proceed slowly.

5           After an appropriately-sized piece of diamond has been cut from a diamond film, it can be attached to a desired object in order to serve as a surface. For example, the diamond may be attached to a substrate by welding, diffusion bonding, adhesion bonding, mechanical fixation or high pressure and high temperature bonding in a press.

10           Although CVD and PVD diamond on a substrate do not exhibit a gradient transition zone that is found in sintered polycrystalline diamond compacts, CVD and PVD process can be conducted in order to incorporate metal into the diamond table. As mentioned elsewhere herein, incorporation of metal into the diamond table enhances adhesion of the diamond table to its substrate and can strengthen the  
15 polycrystalline diamond compact. Incorporation of diamond into the diamond table can be used to achieve a diamond table with a coefficient of thermal expansion and compressibility different from that of pure diamond, and consequently increasing fracture toughness of the diamond table as compared to pure diamond. Diamond  
20 has a low coefficient of thermal expansion and a low compressibility compared to metals. Therefore the presence of metal with diamond in the diamond table achieves a higher and more metal-like coefficient of thermal expansion and the average compressibility for the diamond table than for pure diamond. Consequently, residual stresses at the interface of the diamond table and the substrate are reduced, and delamination of the diamond table from the substrate is less likely.

25           A pure diamond crystal also has low fracture toughness. Therefore, in pure diamond, when a small crack is formed, the entire diamond component fails catastrophically. In comparison, metals have a high fracture toughness and can accommodate large cracks without catastrophic failure. Incorporation of metal into the diamond table achieves a greater fracture toughness than pure diamond. In a  
30 diamond table having interstitial spaces and metal within those interstitial spaces, if a crack forms in the diamond and propagates to an interstitial space containing metal, the crack will terminate at the metal and catastrophic failure will be avoided. Because of this characteristic, a diamond table with metal in its interstitial spaces is able to sustain much higher forces and workloads without catastrophic failure  
35 compared to pure diamond.

Diamond-diamond bonding tends to decrease as metal content in the diamond table increases. CVD and PVD processes can be conducted so that a transition zone is established. However, the surface can be essentially pure

polycrystalline diamond for low wear properties.

Generally CVD and PVD diamond is formed without large interstitial spaces filled with metal. Consequently, most PVD and CVD diamond is more brittle or has a lower fracture toughness than sintered polycrystalline diamond compacts. CVD and  
5 PVD diamond may also exhibit the maximum residual stresses possible between the diamond table and the substrate. It is possible, however, to form CVD and PVD diamond film that has metal incorporated into it with either a uniform or a functionally gradient composition.

One method for incorporating metal into a CVD or PVD diamond film is to use  
10 two different source materials in order to simultaneously deposit the two materials on a substrate in a CVD or PVD diamond production process. This method may be used regardless of whether diamond is being produced by CVD, PVD or a combination of the two.

Another method for incorporating metal into a CVD diamond film is chemical  
15 vapor infiltration. This process would first create a porous layer of material, and then fill the pores by chemical vapor infiltration. The porous layer thickness should be approximately equal to the desired thickness for either the uniform or gradient layer. The size and distribution of the pores can be used to control ultimate composition of the layer. Deposition in vapor infiltration occurs first at the interface between the  
20 porous layer and the substrate. As deposition continues, the interface along which the material is deposited moves outward from the substrate to fill pores in the porous layer. As the growth interface moves outward, the deposition temperature along the interface is maintained by moving the sample relative to a heater or by moving the heater relative to the growth interface. It is imperative that the porous region  
25 between the outside of the sample and the growth interface be maintained at a temperature that does not promote deposition of material (either the pore-filling material or undesired reaction products). Deposition in this region would close the pores prematurely and prevent infiltration and deposition of the desired material in inner pores. The result would be a substrate with open porosity and poor physical  
30 properties.

#### LASER DEPOSITION OF DIAMOND

Another alternative manufacturing process that may be used to produce surfaces and components of the devices involves use of energy beams, such as  
35 laser energy, to vaporize constituents in a substrate and redeposit those constituents on the substrate in a new form, such as in the form of a diamond coating. As an example, a metal, polymeric or other substrate may be obtained or produced containing carbon, carbides or other desired constituent elements. Appropriate

energy, such as laser energy, may be directed at the substrate to cause constituent elements to move from within the substrate to the surface of the substrate adjacent the area of application of energy to the substrate. Continued application of energy to the concentrated constituent elements on the surface of the substrate can be used to  
5 cause vaporization of some of those constituent elements. The vaporized constituents may then be reacted with another element to change the properties and structure of the vaporized constituent elements.

Next, the vaporized and reacted constituent elements (which may be diamond) may be diffused into the surface of the substrate. A separate fabricated  
10 coating may be produced on the surface of the substrate having the same or a different chemical composition than that of the vaporized and reacted constituent elements. Alternatively, some of the changed constituent elements which were diffused into the substrate may be vaporized and reacted again and deposited as a coating on the. By this process and variations of it, appropriate coatings such as  
15 diamond, cubic boron nitride, diamond like carbon,  $B_4C$ ,  $SiC$ ,  $TiC$ ,  $TiN$ ,  $TiB$ ,  $cCN$ ,  $Cr_3C_2$ , and  $Si_3N_4$  may be formed on a substrate.

In other manufacturing environments, high temperature laser application, electroplating, sputtering, energetic laser excited plasma deposition or other methods may be used to place a volume of diamond, diamond-like material, a hard material or  
20 a superhard material in a location in which will serve as a surface.

In light of the disclosure herein, those of ordinary skill in the art will comprehend the apparatuses, materials and process conditions necessary for the formation and use of high quality diamond on a substrate using any of the manufacturing methods described herein in order to create a diamond surface.

25

#### MATERIAL PROPERTY CONSIDERATIONS

There is a particular problem posed by the manufacture of a non-planar diamond surface. The non-planar component design requires that pressures be applied radially in making the part. During the high pressure sintering process,  
30 described in detail below, all displacements must be along a radian emanating from the center of the part that will be produced in order to achieve the desired non-planar geometry. To achieve this in high temperature/high pressure pressing, an isostatic pressure field must be created. During the manufacture of such non-planar parts, if there is any deviatoric stress component, it will result in distortion of the part and may  
35 render the manufactured part useless.

Special considerations that must be taken into account in making non-planar polycrystalline diamond compacts are discussed below.

Modulus

Most polycrystalline diamond compacts include both a diamond table and a substrate. The material properties of the diamond and the substrate may be compatible, but the high pressure and high temperature sintering process in the formation of a polycrystalline diamond compact may result in a component with

5 excessively high residual stresses. For example, for a polycrystalline diamond compact using tungsten carbide as the substrate, the sintered diamond has a Young's modulus of approximately 120 million p.s.i., and cobalt cemented tungsten carbide has a modulus of approximately 90 million p.s.i. Modulus refers to the slope of the curve of the stress plotted against the stress for a material. Modulus indicates

10 the stiffness of the material. Bulk modulus refers to the ratio of isostatic strain to isostatic stress, or the unit volume reduction of a material versus the applied pressure or stress.

Because diamond and most substrate materials have such a high modulus, a very small stress or displacement of the polycrystalline diamond compact can induce

15 very large stresses. If the stresses exceed the yield strength of either the diamond or the substrate, the component will fail. The strongest polycrystalline diamond compact is not necessarily stress free. In a sintered polycrystalline diamond compact with optimal distribution of residual stress, more energy is required to induce a fracture than in a stress free component. Thus, the difference in modulus between

20 the substrate and the diamond must be noted and used to design a component that will have the best strength for its application with sufficient abrasion resistance and fracture toughness.

#### Coefficient of Thermal Expansion (CTE)

The extent to which diamond and its substrate differ in how they deform

25 relative to changes in temperature also affects their mechanical compatibility. Coefficient of thermal expansion ("CTE") is a measure of the unit change of a dimension with unit change in temperature or the propensity of a material to expand under heat or to contract when cooled. As a material experiences a phase change, calculations based on CTE in the initial phase will not be applicable. It is notable that

30 when compacts of materials with different CTE's and modulus are used, they will stress differently at the same stress.

Polycrystalline diamond has a coefficient of thermal expansion (as above and hereafter referred to as "CTE" on the order of 2-4 micro inches per inch ( $10^{-6}$  inches) of material per degree (in/in°C). In contrast, carbide has a CTE on the order of 6-8

35 in/in°C. Although these values appear to be close numerically, the influence of the high modulus creates very high residual stress fields when a temperature gradient of a few hundred degrees is imposed upon the combination of substrate and diamond. The difference in coefficient of thermal expansion is less of a problem in simple

planar polycrystalline diamond compacts than in the manufacture of non-planar or complex shapes. When a non-planar polycrystalline diamond compact is manufactured, differences in the CTE between the diamond and the substrate can cause high residual stress with subsequent cracking and failure of the diamond table, the substrate or both at any time during or after high pressure/high temperature sintering.

#### Dilatoric and Deviatoric Stresses

The diamond and substrate assembly will experience a reduction of free volume during the sintering process. The sintering process, described in detail below, involves subjecting the substrate and diamond assembly to pressure ordinarily in the range of about 40 to about 68 kilobar. The pressure will cause volume reduction of the substrate. Some geometrical distortion of the diamond and/or the substrate may also occur. The stress that causes geometrical distortion is called deviatoric stress, and the stress that causes a change in volume is called dilatoric stress. In an isostatic system, the deviatoric stresses sum to zero and only the dilatoric stress component remains. Failure to consider all of these stress factors in designing and sintering a polycrystalline diamond component with complex geometry (such as concave and convex non-planar polycrystalline diamond compacts) will likely result in failure of the process.

#### Free Volume Reduction of Diamond Feedstock

As a consequence of the physical nature of the feedstock diamond, large amounts of free volume are present unless special preparation of the feedstock is undertaken prior to sintering. It is necessary to eliminate as much of the free volume in the diamond as possible, and if the free volume present in the diamond feedstock is too great, then sintering may not occur. It is also possible to eliminate the free volume during sintering if a press with sufficient ram displacement is employed. Is important to maintain a desired uniform geometry of the diamond and substrate during any process which reduces free volume in the feedstock, or a distorted or faulty component may result.

#### Selection of Solvent-Catalyst Metal

Formation of synthetic diamond in a high temperature and high pressure press without the use of a solvent-catalyst metal is not a viable method at this time, although it may become viable in the future. A solvent-catalyst metal is at this time required to achieve desired crystal formation in synthetic diamond. The solvent-catalyst metal first solvates carbon preferentially from the sharp contact points of the diamond feedstock crystals. It then recrystallizes the carbon as diamond in the interstices of the diamond matrix with diamond-diamond bonding sufficient to achieve a solid with 95 to 97% of theoretical density with solvent metal 5-3% by volume. That

solid distributed over the substrate surface is referred to herein as a polycrystalline diamond table. The solvent-catalyst metal also enhances the formation of chemical bonds with substrate atoms.

5 A method for adding the solvent-catalyst metal to diamond feedstock is by causing it to sweep from the substrate that contains solvent-catalyst metal during high pressure and high temperature sintering. Powdered solvent-catalyst metal may also be added to the diamond feedstock before sintering, particularly if thicker diamond tables are desired. An attritor method may also be used to add the solvent-catalyst metal to diamond feedstock before sintering. If too much or too little solvent-catalyst metal is used, then the resulting part may lack the desired mechanical properties, so it is important to select an amount of solvent-catalyst metal and a method for adding it to diamond feedstock that is appropriate for the particular part to be manufactured.

#### Diamond Feedstock Particle Size and Distribution

15 The durability of the finished diamond product is integrally linked to the size of the feedstock diamond and also to the particle distribution. Selection of the proper size(s) of diamond feedstock and particle distribution depends upon the service requirement of the specimen and also its working environment. The durability of polycrystalline diamond is enhanced if smaller diamond feedstock crystals are used and a highly diamond-diamond bonded diamond table is achieved.

20 Although polycrystalline diamond may be made from single modal diamond feedstock, use of multi-modal feedstock increases both impact strength and wear resistance. The use of a combination of large crystal sizes and small crystal sizes of diamond feedstock together provides a part with high impact strength and wear resistance, in part because the interstitial spaces between the large diamond crystals may be filled with small diamond crystals. During sintering, the small crystals will solvate and reprecipitate in a manner that binds all of the diamond crystals into a strong and tightly bonded compact.

#### Diamond Feedstock Loading Methodology

30 Contamination of the diamond feedstock before or during loading will cause failure of the sintering process. Great care must be taken to ensure the cleanliness of diamond feedstock and any added solvent-catalyst metal or binder before sintering.

35 In order to prepare for sintering, clean diamond feedstock, substrate, and container components are prepared for loading. The diamond feedstock and the substrate are placed into a refractory metal container called a "can" which will seal its contents from outside contamination. The diamond feedstock and the substrate will remain in the can while undergoing high pressure and high temperature sintering in



order to form a polycrystalline diamond compact. The can may be sealed by electron beam welding at high temperature and in a vacuum.

Enough diamond aggregate (powder or grit) is loaded to account for linear shrinkage during high pressure and high temperature sintering. The method used for loading diamond feedstock into a can for sintering affects the general shape and tolerances of the final part. In particular, the packing density of the feedstock diamond throughout the can should be as uniform as possible in order to produce a good quality sintered polycrystalline diamond compact structure. In loading, bridging of diamond can be avoided by staged addition and packing.

The degree of uniformity in the density of the feedstock material after loading will affect geometry of the polycrystalline diamond compact. Loading of the feedstock diamond in a dry form versus loading diamond combined with a binder and the subsequent process applied for the removal of the binder will also affect the characteristics of the finished polycrystalline diamond compact. In order to properly pre-compact diamond for sintering, the pre-compaction pressures should be applied under isostatic conditions.

#### Selection of Substrate Material

The unique material properties of diamond and its relative differences in modulus and CTE compared to most potential substrate materials diamond make selection of an appropriate polycrystalline diamond substrate a formidable task. A great disparity in material properties between the diamond and the substrate creates challenges successful manufacture of a polycrystalline diamond component with the needed strength and durability. Even very hard substrates appear to be soft compared to polycrystalline diamond. The substrate and the diamond must be able to withstand not only the pressure and temperature of sintering, but must be able to return to room temperature and atmospheric pressure without delaminating, cracking or otherwise failing.

Selection of substrate material also requires consideration of the intended application for the part, impact resistance and strengths required, and the amount of solvent-catalyst metal that will be incorporated into the diamond table during sintering. Substrate materials must be selected with material properties that are compatible with those of the diamond table to be formed.

#### Substrate Geometry

Further, it is important to consider whether to use a substrate which has a smooth surface or a surface with topographical features. Substrate surfaces may be formed with a variety of topographical features so that the diamond table is fixed to the substrate with both a chemical bond and a mechanical grip. Use of topographical features on the substrate provides a greater surface area for chemical bonds and

with the mechanical grip provided by the topographical features, can result in a stronger and more durable component.

#### EXAMPLE MATERIALS AND MANUFACTURING STEPS

5 The inventors have discovered and determined materials and manufacturing processes for constructing polycrystalline diamond compacts for use in an articulating diamond-surfaced spinal implant. It is also possible to manufacture the invented surfaces by methods and using materials other than those listed below.

10 The steps described below, such as selection of substrate material and geometry, selection of diamond feedstock, loading and sintering methods, will affect each other, so although they are listed as separate steps that must be taken to manufacture a polycrystalline diamond compact, no step is completely independent of the others, and all steps must be standardized to ensure success of the manufacturing process.

#### 15 Select Substrate and/or Solvent-Catalyst Metal

In order to manufacture any polycrystalline diamond component, an appropriate substrate should be selected. For the manufacture of a polycrystalline diamond component to be used in an articulating diamond-surfaced spinal implant, various substrates may be used as desired.

20

TABLE 2

#### SOME SUBSTRATES FOR ARTICULATING DIAMOND-SURFACED SPINAL IMPLANT APPLICATIONS

SUBSTRATE	ALLOY NAME	REMARKS
Titanium	Ti6/4 (TiAlVa) ASTM F-1313 (TiNbZr) ASTM F-620 ASTM F-1580 TiMbHf Nitinol (TiNi+other)	A thin tantalum barrier may be placed on the titanium substrate before loading diamond feedstock.
Cobalt chrome	ASTM F-799	Contains cobalt, chromium and molybdenum. Wrought product
Cobalt chrome	ASTM F-90	Contains cobalt, chromium, tungsten and nickel.
Cobalt chrome	ASTM F-75	Contains cobalt, chromium and molybdenum. Cast product.

Cobalt chrome	ASTM F-562	Contains cobalt, chromium, molybdenum and nickel.
Cobalt chrome	ASTM F-563	Contains cobalt, chromium, molybdenum, tungsten, iron and nickel.
Tantalum	ASTM F-560 (unalloyed)	refractory metal.
Platinum	various	
Niobium	ASTM F-67 (unalloyed)	refractory metal.
Manganese	Various	May include Cr, Ni, Mg, molybdenum.
Cobalt cemented tungsten carbide	WC	Commonly used in synthetic diamond production
Cobalt chrome cemented tungsten carbide	CoCr cemented WC	
Cobalt chrome cemented chrome carbide	CoCr cemented CrC	
Cobalt chrome cemented silicon carbide	CoCr cemented SiC	
Fused silicon carbide	SiC	
Cobalt chrome molybdenum	CoCrMo	A thin tungsten or tungsten/cobalt layer may be placed on the substrate before loading diamond feedstock.
Stainless steel	Various	

The CoCr used as a substrate or solvent-catalyst metal may be CoCrMo or CoCrW or another suitable CoCr. Alternatively, an Fe-based alloy, a Ni-based alloy (such as Co-Cr-W-Ni) or another alloy may be used. Co and Ni alloys tend to provide a corrosion-resistant component. The preceding substrates and solvent-catalyst metals are examples only. In addition to these substrates, other materials may be appropriate for use as substrates for construction of articulating diamond-surfaced spinal implants and other surfaces.

When titanium is used as the substrate, sometimes place a thin tantalum barrier layer is placed on the titanium substrate. The tantalum barrier prevents mixing of the titanium alloys with cobalt alloys used in the diamond feedstock. If the titanium alloys and the cobalt alloys mix, it possible that a detrimentally low melting point eutectic inter-metallic compound will be formed during the high pressure and

high temperature sintering process. The tantalum barrier bonds to both the titanium and cobalt alloys, and to the polycrystalline diamond that contains cobalt solvent-catalyst metals. Thus, a polycrystalline diamond compact made using a titanium substrate with a tantalum barrier layer and diamond feedstock that has cobalt solvent-catalyst metals can be very strong and well formed. Alternatively, the titanium substrate may be provided with an alpha case oxide coating (an oxidation layer) forming a barrier which prevents formation of a eutectic metal.

If a cobalt chrome molybdenum substrate is used, a thin tungsten layer or a thin tungsten and cobalt layer can be placed on the substrate before loading of the diamond feedstock in order to control formation of chrome carbide (CrC) during sintering.

In addition to those listed, other appropriate substrates may be used for forming polycrystalline diamond compact surfaces. Further, it is possible within the scope of the devices to form a diamond surface for use without a substrate. It is also possible to form a surface from any of the superhard materials and other materials listed herein, in which case a substrate may not be needed. Additionally, if it is desired to use a type of diamond or carbon other than polycrystalline diamond, substrate selection may differ. For example, if a diamond surface is to be created by use of chemical vapor deposition or physical vapor deposition, then use of a substrate appropriate for those manufacturing environments and for the compositions used will be necessary.

#### Determination of Substrate Geometry

A substrate geometry appropriate for the compact to be manufactured and appropriate for the materials being used should be selected. In order to manufacture a non-planar diamond surface, it is necessary to select a substrate geometry that will facilitate the manufacture of those parts. In order to ensure proper diamond formation and avoid compact distortion, forces acting on the diamond and the substrate during sintering must be strictly radial. Therefore the substrate geometry at the contact surface with diamond feedstock for manufacturing a complex surface in some instances may be generally non-planar.

As mentioned previously, there is a great disparity in the material characteristics of synthetic diamond and most available substrate materials. In particular, modulus and CTE are of concern. But when applied in combination with each other, some substrates can form a stable and strong polycrystalline diamond compact. The table below lists physical properties of some substrate materials.

TABLE 3

## MATERIAL PROPERTIES OF SOME EXAMPLE SUBSTRATES

SUBSTRATE MATERIAL	MODULUS	CTE
Ti 6/4	16.5 million psi	5.4
CoCrMo	35.5 million psi	16.9
CoCrW	35.3 million psi	16.3

- 5 Use of either titanium or cobalt chrome substrates alone for the manufacture of non-planar polycrystalline diamond compacts may result in cracking of the diamond table or separation of the substrate from the diamond table. In particular, it appears that titanium's dominant property during high pressure and high temperature sintering is compressibility while cobalt chrome's dominant property during sintering is CTE. In  
10 some embodiments of the devices, a substrate of two or more layers may be used in order to achieve dimensional stability during and after manufacturing.

In various embodiments of the devices, a single layer substrate may be utilized. In other embodiments of the devices, a two-layer substrate may be utilized, as discussed. Depending on the properties of the components being used, however,  
15 it may be desired to utilize a substrate that includes three, four or more layers. Such multi-layer substrates are intended to be comprehended within the scope of the devices.

## Substrate Surface Topography

Depending on the application, it may be advantageous to include substrate  
20 surface topographical features on a substrate that is to be formed into a polycrystalline diamond compact. Regardless whether a one-piece, a two-piece of a multi-piece substrate is used, it may be desirable to modify the surface of the substrate or provide topographical features on the substrate in order to increase the total surface area of diamond to enhance substrate to diamond contact and to  
25 provide a mechanical grip of the diamond table.

The placement of topographical features on a substrate serves to modify the substrate surface geometry or contours from what the substrate surface geometry or contours would be if formed as a simple planar or non-planar figure. Substrate surface topographical features may include one or more different types of  
30 topographical features which result in protruding, indented or contoured features that serve to increase surface, mechanically interlock the diamond table to the substrate, prevent crack formation, or prevent crack propagation.

Substrate surface topographical features or substrate surface modifications serve a variety of useful functions. Use of substrate topographical features increases

total substrate surface area of contact between the substrate and the diamond table. This increased surface area of contact between diamond table and substrate results in a greater total number of chemical bonds between diamond table and substrate than if the substrate surface topographical features were absent, thus achieving a  
5 stronger polycrystalline diamond compact.

Substrate surface topographical features also serve to create a mechanical interlock between the substrate and the diamond table. The mechanical interlock is achieved by the nature of the substrate topographical features and also enhances strength of the polycrystalline diamond compact.

10 Substrate surface topographical features may also be used to distribute the residual stress field of the polycrystalline diamond compact over a larger surface area and over a larger volume of diamond and substrate material. This greater distribution can be used to keep stresses below the threshold for crack initiation and/or crack propagation at the diamond table/substrate interface, within the  
15 diamond itself and within the substrate itself.

Substrate surface topographical features increase the depth of the gradient interface or transition zone between diamond table and substrate, in order to distribute the residual stress field through a longer segment of the composite compact structure and to achieve a stronger part.

20 Substrate surface modifications can be used to create a sintered polycrystalline diamond compact that has residual stresses that fortify the strength of the diamond layer and yield a more robust polycrystalline diamond compact with greater resistance to breakage than if no surface topographical features were used. This is because in order to break the diamond layer, it is necessary to first overcome  
25 the residual stresses in the part and then overcome the strength of the diamond table.

Substrate surface topographical features redistribute forces received by the diamond table. Substrate surface topographical features cause a force transmitted through the diamond layer to be re-transmitted from single force vector along multiple  
30 force vectors. This redistribution of forces traveling to the substrate avoids conditions that would deform the substrate material at a more rapid rate than the diamond table, as such differences in deformation can cause cracking and failure of the diamond table.

Substrate surface topographical features may be used to mitigate the  
35 intensity of the stress field between the diamond and the substrate in order to achieve a stronger part.

Substrate surface topographical features may be used to distribute the residual stress field throughout the polycrystalline diamond compact structure in

order to reduce the stress per unit volume of structure.

Substrate surface topographical features may be used to mechanically interlock the diamond table to the substrate by causing the substrate to compress over an edge of the diamond table during manufacturing. Dovetailed, heminon-  
5 planar and lentate modifications act to provide force vectors that tend to compress and enhance the interface of diamond table and substrate during cooling as the substrate dilates radially.

Substrate surface topographical features may also be used to achieve a manufacturable form. As mentioned herein, differences in coefficient of thermal expansion and modulus between diamond and the chosen substrate may result in  
10 failure of the polycrystalline diamond compact during manufacturing. For certain parts, the stronger interface between substrate and diamond table that may be achieved when substrate topographical features are used can achieve a polycrystalline diamond compact that can be successfully manufactured. But if a  
15 similar part of the same dimensions is to be made using a substrate with a simple substrate surface rather than specialized substrate surface topographical features, the diamond table may crack or separate from the substrate due to differences in coefficient of thermal expansion or modulus of the diamond and the substrate.

Examples of useful substrate surface topographical features include waves,  
20 grooves, ridges, other longitudinal surface features (any of which may be arranged longitudinally, latitudinally, crossing each other at a desired angle, in random patterns, and in geometric patterns), three dimensional textures, non-planar segment depressions, non-planar segment protrusions, triangular depressions, triangular protrusions, arcuate depressions, arcuate protrusions, partially non-planar  
25 depressions, partially non-planar protrusions, cylindrical depressions, cylindrical protrusions, rectangular depressions, rectangular protrusions, depressions of n-sided polygonal shapes where n is an integer, protrusions of n-sided polygonal shapes, a waffle pattern of ridges, a waffle iron pattern of protruding structures, dimples, nipples, protrusions, ribs, fenestrations, grooves, troughs or ridges that have a cross-  
30 sectional shape that is rounded, triangular, arcuate, square, polygonal, curved, or otherwise, or other shapes. Machining, pressing, extrusion, punching, injection molding and other manufacturing techniques for creating such forms may be used to achieve desired substrate topography. Although for illustration purposes, some sharp corners are depicted on substrate topography or other structures in the  
35 drawings, in practice it is expected that all corners will have a small radius to achieve a component with superior durability.

Although many substrate topographies have been depicted in convex non-planar substrates, those surface topographies may be applied to convex non-planar

substrate surfaces, other non-planar substrate surfaces, and flat substrate surfaces. Substrate surface topographies which are variations or modifications of those shown, and other substrate topographies which increase component strength or durability may also be used.

5 Diamond Feedstock Selection

It is anticipated that typically the diamond particles used will be in the range of less than 1 micron to more than 100 microns. In some embodiments of the devices, however, diamond particles as small as 1 nanometer may be used. Smaller diamond particles are used for smoother surfaces. Commonly, diamond particle sizes will be  
10 in the range of 0.5 to 2.0 microns or 0.1 to 10 microns.

An example diamond feedstock is shown in the table below.

TABLE 4

EXAMPLE BIMODAL DIAMOND FEEDSTOCK

15

MATERIAL	AMOUNT
4 to 8 micron diamond	about 90%
0.5 to 1.0 micron diamond	about 9%
Titanium carbonitride powder	about 1%

20

This formulation mixes some smaller and some larger diamond crystals so that during sintering, the small crystals may dissolve and then recrystallize in order to form a lattice structure with the larger diamond crystals. Titanium carbonitride powder may optionally be included in the diamond feedstock in order to prevent excessive diamond grain growth during sintering in order to produce a finished product that has smaller diamond crystals.

Another diamond feedstock example is provided in the table below.

TABLE 5

25

EXAMPLE TRIIMODAL DIAMOND FEEDSTOCK

MATERIAL	AMOUNT
Size x diamond crystals	about 90%
Size 0.1x diamond crystals	about 9%
Size 0.01x diamond crystals	about 1%

The trimodal diamond feedstock described above can be used with any suitable diamond feedstock having a first size or diameter "x", a second size 0.1x and a third size 0.01x. This ratio of diamond crystals allows packing of the feedstock to about



89% theoretical density, closing most interstitial spaces and providing the densest diamond table in the finished polycrystalline diamond compact.

Another diamond feedstock example is provided in the table below.

TABLE 6

## 5 EXAMPLE TRIIMODAL DIAMOND FEEDSTOCK

MATERIAL	AMOUNT
Size x diamond crystals	about 88-92%
Size 0.1x diamond crystals	about 8-12%
Size 0.01x diamond crystals	about 0.8-1.2%

Another diamond feedstock example is provided in the table below.

TABLE 7

10

## EXAMPLE TRIIMODAL DIAMOND FEEDSTOCK

MATERIAL	AMOUNT
Size x diamond crystals	about 85-95%
Size 0.1x diamond crystals	about 5-15%
Size 0.01x diamond crystals	about 0.5-1.5%

Another diamond feedstock example is provided in the table below.

15

TABLE 8

## EXAMPLE TRIIMODAL DIAMOND FEEDSTOCK

MATERIAL	AMOUNT
Size x diamond crystals	about 80-90%
Size 0.1x diamond crystals	about 10-20%
Size 0.01x diamond crystals	about 0-2%

In some embodiments of the devices, the diamond feedstock used will be diamond powder having a greatest dimension of about 100 nanometers or less. In some embodiments of the devices some solvent-catalyst metal is included with the diamond feedstock to aid in the sintering process, although in many applications there will be a significant solvent-catalyst metal sweep from the substrate during sintering as well.

## 25 Solvent Metal Selection

It has already been mentioned that solvent metal will sweep from the substrate through the diamond feedstock during sintering in order to solvate some diamond crystals so that they may later recrystallize and form a diamond-diamond bonded lattice network that characterizes polycrystalline diamond. It is possible to include some solvent-catalyst metal in the diamond feedstock only when required to supplement the sweep of solvent-catalyst metal from the substrate.

Traditionally, cobalt, nickel and iron have been used as solvent metals for making polycrystalline diamond. Platinum and other materials could also be used for a binder.

CoCr may be used as a solvent-catalyst metal for sintering PCD to achieve a more wear resistant PDC. Infiltrating diamond particles with Cobalt (Co) metal produces standard polycrystalline diamond compact. As the cobalt infiltrates the diamond, carbon is dissolved (mainly from the smaller diamond grains) and reprecipitates onto the larger diamond grains causing the grains to grow together. This is known as liquid phase sintering. The remaining pore spaces between the diamond grains are filled with cobalt metal.

In this example, the alloy Cobalt Chrome (CoCr) may be used as the solvent metal which acts similarly to Co metal. However, it differs in that the CoCr reacts with some of the dissolved carbon resulting in the precipitation of CoCr carbides. These carbides, like most carbides, are harder (abrasion resistant) than cobalt metal and results in a more wear or abrasion resistant PDC.

Other metals can be added to Co to form metal carbides as precipitates within the pore spaces between the diamond grains. These metals include the following, but not limited to, Ti, W, Mo, V, Ta, Nb, Zr, Si, and combinations thereof.

It is important not just to add the solvent metal to diamond feedstock, but also to include solvent metal in an appropriate proportion and to mix it evenly with the feedstock. The use of about 86% diamond feedstock and 15% solvent metal by mass (weight) has provided good result, other useful ratios of diamond feedstock to solvent metal may include 5:95, 10:90, 20:80, 30:70, 40:60, 50:50, 60:40, 65:35, 75:25, 80:20, 90:10, 95:5, 97:3, 98:2, 99:1, 99.5:0.5, 99.7:0.3, 99.8:0.2, 99.9:0.1 and others.

In order to mix the diamond feedstock with solvent-catalyst metal, first the amounts of feedstock and solvent metal to be mixed may be placed together in a mixing bowl, such as a mixing bowl made of the desired solvent-catalyst metal. Then the combination of feedstock and solvent metal may be mixed at an appropriate speed (such as 200 rpm) with dry methanol and attritor balls for an appropriate time period, such as 30 minutes. The attritor balls, the mixing fixture and the mixing bowl may be made from the solvent-catalyst metal. The methanol may then be decanted

and the diamond feedstock separated from the attritor balls. The feedstock may then be dried and cleaned by firing in a molecular hydrogen furnace at about 1000 degrees Celsius for about 1 hour. The feedstock is then ready for loading and sintering. Alternatively, it may be stored in conditions which will preserve its cleanliness. Appropriate furnaces which may be used for firing also include hydrogen plasma furnaces and vacuum furnaces.

#### Loading Diamond Feedstock

Referring to Figure 3, an apparatus for carrying out a loading technique is depicted. The apparatus includes a spinning rod 301 with a longitudinal axis 302, the spinning rod being capable of spinning about its longitudinal axis. The spinning rod 701 has an end 303 matched to the size and shape of the part to be manufactured. For example, if the part to be manufactured is non-planar, the spinning rod end 303 may be heminon-planar.

A compression ring 304 is provided with a bore 305 through which the spinning rod 301 may project. A die 306 or can is provided with a cavity 307 also matched to the size and shape of the part to be made.

In order to load diamond feedstock, the spinning rod is placed into a drill chuck and the spinning rod is aligned with the center point of the die. The depth to which the spinning rod stops in relation to the cavity of the die is controlled with a set screw and monitored with a dial indicator.

The die is charged with a known amount of diamond feedstock material. The spinning rod is then spun about its longitudinal axis and lowered into the die cavity to a predetermined depth. The spinning rod contacts and rearranges the diamond feedstock during this operation. Then the spinning of the spinning rod is stopped and the spinning rod is locked in place.

The compression ring is then lowered around the outside of the spinning rod to a point where the compression ring contacts diamond feedstock in the cavity of the die. The part of the compression ring that contacts the diamond is annular. The compression ring is tamped up and down to compact the diamond. This type of compaction is used to distribute diamond material throughout the cavity to the same density and may be done in stages to prevent bridging. Packing the diamond with the compaction ring causes the density of the diamond around the equator of the sample caused to be very uniform and the same as that of the polar region in the cavity. In this configuration, the diamond sinters in a truly non-planar fashion and the resulting part maintains its sphericity to close tolerances.

#### Controlling Large Volumes of Powder Feedstocks, Such As Diamond

The following information provides further instruction on control and pre-processing of diamond feedstock before sintering. Polycrystalline Diamond Compact

(PDC) and Polycrystalline Cubic Boron Nitride (PCBN) powders reduce in volume during the sintering process. The amount of shrinkage experienced is dependent on a number of factors such as:

- a. The amount of metal mixed with the diamond.
- 5      b. The loading density of the powders.
- c. The bulk density of diamond metal mix.
- d. The volume of powder loaded.
- e. Particle size distribution (PSD) of the powders.

In most PDC and CBN sintering applications, the volume of powder used is small enough that shrinkage is easily managed, as shown in Figure 3A-1. In Figure 10      3A, we can see a can 3A-54 in which can halves 3A-53 contain a substrate 3A-52 and a diamond table 3A-51. However, when sintering large volumes of diamond powders in spherical configurations, shrinkage is great enough to cause buckling of the containment cans 3A-66 as shown in Figure 3A-2 and the cross section of Figure 15      3A-3. The diamond has sintered 3A-75 but the can has buckles 3A-77 and wrinkles 3A-78, resulting in a non-uniform and damaged part. The following method is an improved loading, pre-compression, densification, and refractory can sealing method for spherical and non-planar parts loaded with large volumes of diamond and/or metal powders. The processing steps are described below.

20      Referring to Figure 3A-4 and its cross section at Figure 3A-5, PDC or PCBN powders 3A-911 are loaded against a substrate 3A-99 and into a refractory metal containment can 3A-910 having a seal 3A-912. Extra powder may be loaded normal to the seam in the cans to accommodate shrinkage.

25      Referring to Figure 3A-6, a can assembly 3A-913 is placed into compaction fixture 3A-1014, which may be a cylindrical holder or slide 3A-1015 with two hemispherical punches 3A-1016 and 3A-1017. The fixture is designed to support the containment cans and allow the cans to slip at the seam during the pressing operation.

30      Referring to Figure 3A-7-1, relationship of the can half skins 3A-910 with the junction 3A-912 and the punch 3A-1016 is seen.

Referring to Figure 3A-7, fixture 3A-1014 with can 3A-913 is placed into a press 3A-1218 and the upper and lower punches compress the can assembly. The containment can halves slip past each other preventing buckling while the powdered feedstock is compressed.

35      Referring to Figure 3A-8, the upper punch is retracted and a crimping die is attached to the cylinder.

Referring to Figures 3A-9 and 3A-9-1, the lower punch is raised driving excess can material into the hemispherical portion of the crimping die folding the excess around the upper can.

Referring to Figure 3A-10, the lower punch is raised expelling the can  
5 assembly from the cylinder.

Referring to Figure 3A-11, the can assembly emerges from pressing operation spherical with high loading density. The part can then be sintered in a cubic or other press without buckling or breaking the containment cans.

#### Binding Diamond Feedstock Generally

10 Another method which may be employed to maintain a uniform density of the feedstock diamond is the use of a binder. A binder is added to the correct volume of feedstock diamond, and then the combination is pressed into a can. Some binders which might be used include polyvinyl butyryl, polymethyl methacrylate, polyvinyl formol, polyvinyl chloride acetate, polyethylene, ethyl cellulose, methylabietate,  
15 paraffin wax, polypropylene carbonate and polyethyl methacrylate.

In one embodiment of the devices, the process of binding diamond feedstock includes four steps. First, a binder solution is prepared. A binder solution may be prepared by adding about 5 to 25% plasticizer to pellets of poly(propylene carbonate), and dissolving this mixture in solvent such as 2-butanone to make about  
20 a 20% solution by weight.

Plasticizers that may be used include nonaqueous binders generally, glycol, dibutyl phthalate, benzyl butyl phthalate, alkyl benzyl phthalate, diethylhexyl phthalate, diisooctyl phthalate, diisononyl phthalate, dimethyl phthalate, dipropylene glycol dibenzoate, mixed glycols dibenzoate, 2-ethylhexyl diphenyl dibenzoate, mixed  
25 glycols dibenzoate, 2-ethylhexyl diphenyl phosphate, isodecyl diphenyl phosphate, isodecyl diphenyl phosphate, tricrestyl phosphate, tributoxy ethyl phosphate, dihexyl adipate, triisooctyl trimellitate, dioctyl phthalate, epoxidized linseed oil, epoxidized soybean oil, acetyl triethyl citrate, propylene carbonate, various phthalate esters, butyl stearate, glycerin, polyalkyl glycol derivatives, diethyl oxalate, paraffin wax and  
30 triethylene glycol. Other appropriate plasticizers may be used as well.

Solvents that may be used include 2-butanone, methylene chloride, chloroform, 1,2-dichloroethane, trichlorethylene, methyl acetate, ethyl acetate, vinyl acetate, propylene carbonate, n-propyl acetate, acetonitrile, dimethylformamide, propionitrile, n-methyl-2-pyrrolidone, glacial acetic acid, dimethyl sulfoxide, acetone,  
35 methyl ethyl ketone, cyclohexanone, oxysolve 80a, caprolactone, butyrolactone, tetrahydrofuran, 1,4 dioxane, propylene oxide, cellosolve acetate, 2-methoxy ethyl ether, benzene, styrene, xylene, ethanol, methanol, toluene, cyclohexane,

chlorinated hydrocarbons, esters, ketones, ethers, ethyl benzene and various hydrocarbons. Other appropriate solvents may be used as well.

Second, diamond is mixed with the binder solution. Diamond may be added to the binder solution to achieve about a 2-25% binder solution (the percentage is  
5 calculated without regard to the 2-butanone).

Third, the mixture of diamond and binder solution is dried. This may be accomplished by placing the diamond and binder solution mixture in a vacuum oven for about 24 hours at about 50 degrees Celsius in order to drive out all of the solvent 2-butanone. Fourth, the diamond and binder may be pressed into shape. When the  
10 diamond and binder is removed from the oven, it will be in a clump that may be broken into pieces which are then pressed into the desired shape with a compaction press. A pressing spindle of the desired geometry may be contacted with the bound diamond to form it into a desired shape. When the diamond and binder have been pressed, the spindle is retracted. The final density of diamond and binder after  
15 pressing may be at least about 2.6 grams per cubic centimeter.

If a volatile binder is used, it should be removed from the shaped diamond prior to sintering. The shaped diamond is placed into a furnace and the binding agent is either gasified or pyrolyzed for a sufficient length of time such that there is no binder remaining. Polycrystalline diamond compact quality is reduced by foreign  
20 contamination of the diamond or substrate, and great care must be taken to ensure that contaminants and binder are removed during the furnace cycle. Ramp up and the time and temperature combination are critical for effective pyrolyzation of the binder. For the binder example given above, the debinding process that may be used to remove the binder is as follows. Reviewing Figure 4 while reading this  
25 description may be helpful.

First, the shaped diamond and binder are heated to from ambient temperature to about 500 degrees Celsius. The temperature may be increased by about 2 degrees Celsius per minute until about 500 degrees Celsius is reached. Second, the temperature of the bound and shaped diamond is maintained at about  
30 500 degrees Celsius for about 2 hours. Third, the temperature of the diamond is increased again. The temperature may be increased from about 500 degrees Celsius by about 4 degrees per minute until a temperature of about 950 degrees Celsius is reached. Fourth, the diamond is maintained at about 950 degrees Celsius for about 6 hours. Fifth, the diamond is then permitted to return to ambient  
35 temperature at a temperature decrease of about 2 degrees per minute.

In some embodiments of the devices, it may be desirable to preform bound diamond feedstock by an appropriate process, such as injection molding. The diamond feedstock may include diamond crystals of one or more sizes, solvent-

catalyst metal, and other ingredients to control diamond recrystallization and solvent-catalyst metal distribution. Handling the diamond feedstock is not difficult when the desired final curvature of the part is flat, convex dome or conical. However, when the desired final curvature of the part has complex contours, such as illustrated herein, providing uniform thickness and accuracy of contours of the polycrystalline diamond compact is more difficult when using powder diamond feedstock. In such cases it may be desirable to perform the diamond feedstock before sintering.

If it is desired to perform diamond feedstock prior to loading into a can for sintering, rather than placing powder diamond feedstock into the can, the steps described herein and variations of them may be followed. First, as already described, a suitable binder is added to the diamond feedstock. Optionally, powdered solvent-catalyst metal and other components may be added to the feedstock as well. The binder will typically be a polymer chosen for certain characteristics, such as melting point, solubility in various solvents, and CTE. One or more polymers may be included in the binder. The binder may also include an elastomer and/or solvents as desired in order to achieve desired binding, fluid flow and injection molding characteristics. The working volume of the binder to be added to a feedstock may be equal to or slightly more than the measured volume of empty space in a quantity of lightly compressed powder. Since binders typically consist of materials such as organic polymers with relatively high CTE's, the working volume should be calculated for the injection molding temperatures expected. The binder and feedstock should be mixed thoroughly to assure uniformity of composition. When heated, the binder and feedstock will have sufficient fluid character to flow in high pressure injection molding. The heated feedstock and binder mixture is then injected under pressure into molds of desired shape. The molded part then cools in the mold until set, and the mold can then be opened and the part removed. Depending on the final polycrystalline diamond compact geometry desired, one or more molded diamond feedstock component can be created and placed into a can for polycrystalline diamond compact sintering. Further, use of this method permits diamond feedstock to be molded into a desired form and then stored for long periods of time prior to use in the sintering process, thereby simplifying manufacturing and resulting in more efficient production.

As desired, the binder may be removed from the injection molded diamond feedstock form. A variety of methods are available to achieve this. For example, by simple vacuum or hydrogen furnace treatment, the binder may be removed from the diamond feedstock form. In such a method, the form would be brought up to a desired temperature in a vacuum or in a very low pressure hydrogen (reducing) environment. The binder will then volatilize with increasing temperature and will be

removed from the form. The form may then be removed from the furnace. When hydrogen is used, it helps to maintain extremely clean and chemically active surfaces on the diamond crystals of the diamond feedstock form.

An alternative method for removing the binder from the form involves utilizing two or polymer (such as polyethylene) binders with different molecular weights. After initial injection molding, the diamond feedstock form is placed in a solvent bath which removes the lower molecular weight polymer, leaving the higher molecular weight polymer to maintain the shape of the diamond feedstock form. Then the diamond feedstock form is placed in a furnace for vacuum or very low pressure hydrogen treatment for removal of the higher molecular weight polymer.

Partial or complete binder removal from the diamond feedstock form may be performed prior to assembly of the form in a pressure assembly for polycrystalline diamond compact sintering. Alternatively, the pressure assembly including the diamond feedstock form may be placed into a furnace for vacuum or very low pressure hydrogen furnace treatment and binder removal.

#### Dilute Binder

In some embodiments, dilute binder may be added to PCD, PCBN or ceramic powders to hold form. This technique may be used to provide an improved method of forming Polycrystalline Diamond Compact (PDC), Polycrystalline Cubic Boron Nitride (PCBN), ceramic, or cermet powders into layers of various geometries. A PDC, PCBN, ceramic or cermet powder may be mixed with a temporary organic binder. This mixture may be mixed and cast or calendared into a sheet (tape) of the desired thickness. The sheet may be dried to remove water or organic solvents. The dried tape may be then cut into shapes needed to conform to the geometry of a corresponding substrate. The tape/substrate assembly may be then heated in a vacuum furnace to drive off the binder material. The temperature may be then raised to a level where the ceramic or cermet powder fuses to itself and/or to the substrate, thereby producing a uniform continuous ceramic or cermet coating bonded to the substrate.

Referring to Figure 5, a die 55 with a cup/can in it 54 and diamond feedstock against it 52 are depicted. A punch 53 is used to form the diamond feedstock into a desired shape. Binder liquid 51 is not added to the powder until after the diamond, PCBN, ceramic or cermet powder 52 is in the desired geometry. Dry powder 52 is spin formed using a rotating formed punch 53 in a refractory containment can 54 supported in a holding die 55. In another method shown in Figure 6, feedstock powder 62 is added to a mold 66. A punch forms the feedstock to shape. A vibrator 67 may be used help the powder 62 take on the shape of the mold 66. After the



powder feedstock is in the desired geometry, a dilute solution of an organic binder with a solvent is allowed to percolate through the powder granules.

As shown in Figures 7 and 8, one powder layer 88 can be loaded, and after a few minutes, when the binder is cured sufficiently at room temperature, another layer 89 can be loaded on top of the first layer 88. This method is particularly useful in producing PDC or CBN with multiple layers of varying powder particle size and metal content. The process can be repeated to produce as many layers as desired. Figure 7 shows a section view of a spherical, multi-layered powder load using a first layer 88, second layer 89, third layer 810, and final layer 811. The binder content should be kept to minimum to produce good loading density and to limit the amount of gas produced during the binder removal phase to reduce the tendency of the containment cans being displaced from a build up of internal pressure.

Once all of the powder layers are loaded the binder may be burned-out in a vacuum oven at a vacuum of about 200 Millitorrs or less and at the time and desired temperature profile, such as that shown in Figure 9. An acceptable binder is 0.5 to 5% propylene carbonate in methyl ethyl ketone. An example binder burn out cycle that may be used to remove binder is as follows:

Time (minutes)	Temperature (degrees Centigrade)
0	21
4	100
8	250
60	250
140	800
170	800
290	21

## Gradients

Diamond feedstock may be selected and loaded in order to create different types of gradients in the diamond table. These include an interface gradient diamond table, an incremental gradient diamond table, and a continuous gradient diamond table.

If a single type or mix of diamond feedstock is loaded adjacent a substrate, as discussed elsewhere herein, sweep of solvent-catalyst metal through the diamond will create an interface gradient in the gradient transition zone of the diamond table.

An incremental gradient diamond table may be created by loading diamond feedstocks of differing characteristics (diamond particle size, diamond particle distribution, metal content, etc.) in different strata or layers before sintering. For

example, a substrate is selected, and a first diamond feedstock containing 60% solvent-catalyst metal by weight is loaded in a first strata adjacent the substrate. Then a second diamond feedstock containing 40% solvent-catalyst metal by weight is loaded in a second strata adjacent the first strata. Optionally, additional strata of diamond feedstock may be used. For example, a third strata of diamond feedstock containing 20% solvent-catalyst metal by weight may be loaded adjacent the second strata.

A continuous gradient diamond table may be created by loading diamond feedstock in a manner that one or more of its characteristics continuously vary from one depth in the diamond table to another. For example, diamond particle size may vary from large near a substrate (in order to create large interstitial spaces in the diamond for solvent-catalyst metal to sweep into) to small near the diamond surface in order to create a part that is strongly bonded to the substrate but that has a very low friction surface.

The diamond feedstocks of the different strata may be of the same or different diamond particle size and distribution. Solvent-catalyst metal may be included in the diamond feedstock of the different strata in weight percentages of from about 0% to more than about 80%. In some embodiments, diamond feedstock will be loaded with no solvent-catalyst metal in it, relying on sweep of solvent-catalyst metal from the substrate to achieve sintering. Use of a plurality of diamond feedstock strata, the strata having different diamond particle size and distribution, different solvent-catalyst metal by weight, or both, allows a diamond table to be made that has different physical characteristics at the interface with the substrate than at the surface. This allows a polycrystalline diamond compact to be manufactured which has a diamond table very firmly bonded to its substrate.

#### Bisquing Processes to Hold Shapes

If desired, a bisquing process may be used to hold shapes for subsequent processing of polycrystalline diamond compacts, polycrystalline cubic boron nitride, and ceramic or cermet products. This involves an interim processing step in High Temperature High Pressure (HTHP) sintering of Polycrystalline Diamond Compact (PDC), Polycrystalline Boron Nitride (PCBN), ceramic, or cermet powders called "bisquing." Bisquing may provide the following enhancements to the processing of the above products:

- a. Pre-sintered shapes can be controlled that are at a certain density and size.
- b. Product consistency is improved dramatically.
- c. Shapes can be handled easily in the bisque form.
- d. In layered constructs, bisquing keeps the different layers from contaminating each other.

- e. Bisquing different components or layers separately increase the separation of work elements increasing production efficiency and quality.
- f. Bisquing molds are often easier to handle and manage prior to final assembly that the smaller final product forms.

5        Bisquing molds or containers can be fabricated from any high temperature material that has a melting point higher than the highest melting point of any mix component to be bisque. Bisque mold / container materials that work well are Graphite, Quartz, Solid Hexagonal Boron Nitride (HBN), and ceramics. Some refractory type metals (High temperature stainless steels, Nb, W, Ta, Mo, etc) work  
10       well in some applications where bisquing temperatures are lower and sticking of the bisque powder mix is not a problem. Molds or containers can be shaped by pressing, forming, or machining, and are preferably polished at the interface between the bisque material and the mold / container itself. Some mold / container materials glazing and /or firing prior to use.

15       Figure 10 shows an embodiment 1006 for making a cylinder with a concave relief or trough using the bisquing process. Pre-mixed powders of PDC, PCBN, ceramic, or cermet materials 1001 which contain enough metal to undergo solid phase sintering are loaded into the bisquing molds or containers 1002 and 1004. A release agent may be required between the mold / container to ensure that the final bisque  
20       form can be removed following furnace firing. Some release agents that may be used are HBN, Graphite, Mica, and Diamond Powder. A bisque mold / container lid with an integral support form 1005 is placed over the loaded powder material to ensure that the material holds form during the sintering process. The bisque mold / container assembly is then placed in a hydrogen atmosphere furnace, or alternately,  
25       in a vacuum furnace which is drawn to a vacuum ranging from 200 to 0 Millitorrs. The load is then heated within a range of 0.6 to 0.8 of the melting temperature of the largest volume mix metal. A typical furnace cycle is shown in Figure 12. Once the furnace cycle is completed and the mold / container is cooled, the hardened bisque formed powders can be removed for further HPHT processing. A bisque form of  
30       feedstock 1003 is the net product.

      Figure 11 shows fabrication 1110 of a bisque form for a full hemispherical part 1109 that has multiple powder layers 1107a and 1107b. Pre-mixed powders of PDC, PCBN, ceramic, or cermet materials which contain enough metal to undergo solid phase sintering are loaded into the bisquing molds or containers. A release agent  
35       may be required between the mold / container to ensure that the final bisque form can be removed following furnace firing. The bisque mold / container assembly may then be placed in a vacuum furnace which is drawn to a vacuum ranging from 200 to 0 Millitorrs. The load is then heated within a range of 0.6 to 0.8 of the melting

temperature of the largest volume mix metal. Once the furnace cycle is completed and the mold / container is cooled, the hardened bisque 1109 formed powders can be removed for further HPHT processing. An example of a bisque binder burn-out cycle that may be used to remove the unwanted materials before sintering is as follows:

Time (hours)	Temperature (degrees Centigrade)
0	21
0.25	21
5.19	800
6.19	800
10.19	21

#### Reduction of Free Volume in Diamond Feedstock

As mentioned earlier, it may be desirable to remove free volume in the diamond feedstock before sintering is attempted. This may be a useful procedure especially when producing non-planar concave and convex parts. If a press with sufficient anvil travel is used for high pressure and high temperature sintering, however, this step may not be necessary. Free volume in the diamond feedstock may in some instances be reduced so that the resulting diamond feedstock is at least about 95% theoretical density and sometimes closer to about 97% of theoretical density.

Referring to Figures 13 and 14a, an assembly used for precompressing diamond to eliminate free volume is depicted. In the drawing, the diamond feedstock is intended to be used to make a convex non-planar polycrystalline diamond part. The assembly may be adapted for precompressing diamond feedstock for making polycrystalline diamond compacts of other complex shapes.

The assembly depicted includes a cube 1301 of a pressure transfer medium. A cube is made from pyrophyllite or other appropriate pressure transfer material such as a synthetic pressure medium and is intended to undergo pressure from a cubic press with anvils simultaneously pressing the six faces of the cube. A cylindrical cell rather than a cube would be used if a belt press were utilized for this step.

The cube 801 has a cylindrical cavity 1302 or passage through it. The center of the cavity 1302 will receive a non-planar refractory metal can 1310 loaded with diamond feedstock 806 that is to be precompressed. The diamond feedstock 1306 may have a substrate with it.

The can 1310 consists of two heminon-planar can halves 1310a and 1310b, one of which overlaps the other to form a slight lip 1312. The can may be an

appropriate refractory metal such as niobium, tantalum, molybdenum, etc. The can is typically two hemispheres, one which is slightly larger to accept the other being slid inside of it to fully enclosed the diamond feedstock. A rebated area or lip is provided in the larger can so that the smaller can will satisfactorily fit therein. The seam of the can is sealed with an appropriate sealant such as dry hexagonal boronitride or a synthetic compression medium. The sealant forms a barrier that prevents the salt pressure medium from penetrating the can. The can seam may also be welded by plasma, laser, or electron beam processes.

An appropriately shaped pair of salt domes 1304 and 1307 surround the can 1310 containing the diamond feedstock 1306. In the example shown, the salt domes each have a hemicon-planar cavity 1305 and 1308 for receiving the can 1310 containing the non-planar diamond feedstock 1306. The salt domes and the can and diamond feedstock are assembled together so that the salt domes encase the diamond feedstock. A pair of cylindrical salt disks 1303 and 1309 are assembled on the exterior of the salt domes 1304 and 1307. All of the aforementioned components fit within the bore 1302 of the pressure medium cube 1301.

The entire pyrocube assembly is placed into a press and pressurized under appropriate pressure (such as about 40-68 Kbar) and for an appropriate although brief duration to precompress the diamond and prepare it for sintering. No heat is necessary for this step.

#### Mold Releases

When making non-planar shapes, it may be desirable to use a mold in the sintering process to produce the desired net shape. CoCr metal may be used as a mold release in forming shaped diamond or other superhard products. Sintering the superhard powder feed stocks to a substrate, the object of which is to lend support to the resulting superhard table, may be utilized to produce standard Polycrystalline Diamond Compact (PDC) and Polycrystalline Cubic Boron Nitride (PCBN) parts. However, in some applications, it is desired to remove the diamond table from the substrate.

Referring to Figure 14, a diamond layer 1402 and 1403 has been sintered to a substrate 1401 at an interface 1404. The interface 1404 must be broken to result in free standing diamond if the substrate is not required in the final product. A mold release may be used to remove the substrate from the diamond table. If CoCr alloy is used for the substrate, then the CoCr itself serves as a mold release, as well as serving as a solvent-catalyst metal. CoCr works well as a mold release because its Coefficient of Thermal Expansion (CTE) is dramatically different than that of sintered PDC or PCBN. Because of the large disparity in the CTE's between PDC and PCBN and CoCr, high stress is formed at the interface 1501 between these two

materials as shown in Figure 15. The stress that is formed is greater than the bond energy between the two materials. When the stress is greater than the bond energy, a crack is formed at the point of highest stress. The crack then propagates following the narrow region of high stress concentrated at the interface. Referring to Figure 5 16, in this way, the CoCr substrate 1601 will separate from the PCD or PCBN 1602 that was sintered around it, regardless of the shape of the interface.

Materials other than CoCr can be used as a mold release. These materials include those metals with high CTE's and, in particular, those that are not good carbide formers. These are, for example, Co, Ni, CoCr, CoFe, CoNi, Fe, steel, etc.

#### 10 Gradient Layers and Stress Modifiers

Gradient layers and stress modifiers may be used in the making of superhard constructs. Gradient layers may be used to achieve any of the following objectives:

- 15 a. Improve the "sweep" of solvent metal into the outer layer of superhard material and to control the amount of solvent metal introduced for sintering into said outer layer.
- b. Provide a "sweep" source to flush out impurities for deposit on the surface of the outer layer of superhard material and/or chemical attachment/combination with the refractory containment cans.
- 20 c. Control the Bulk Modulus of the various gradient layers and thereby control the overall dilatation of the construct during the sintering process.
- d. Affect the "Coefficient of Thermal Expansion" (CTE) of each of the various layers by changing the ratio of metal or carbides to diamond, PCBN or other Superhard materials to reduce the CTE of an individual 25 gradient layer.
- e. Allow for the control of structural stress fields through the various levels of gradient layers to optimize the overall construct.
- f. Change the direction of stress tensors to improve the outer Superhard layer, e.g., direct the tensor vectors toward the center of a spherical 30 construct to place the outer layer diamond into compression, or conversely, direct the tensor vectors from the center of the construct to reduce interface stresses between the various gradient layers.
- g. Improve the overall structural stress compliance to external or internal 35 brittleness and increased toughness wherein loads are transferred through the construct without crack initiation and propagation.

Referring to Figure 17, The liquid sintering phase of Polycrystalline Diamond (PDC) and Polycrystalline Cubic Boron Nitride (PCBN) is typically accomplished by mixing the solvent sintering metal 1701 directly with the Diamond or PCBN powders 1702 prior to the "High Temperature High Pressure (HPHT) pressing, or (referring to Figure 18) "sweeping"  
5 the solvent metal 1802 from a substrate 1801 into feedstock powders from the adjacent substrate during HPHT. The very best high quality PDC or PCBN is created using the "sweep" process.

There are several theories related to the increased PDC and CBH quality when using the sweep method. However, most of those familiar with the field agree  
10 that allowing the sintering metal to "sweep" from the substrate material provides a "wave front" of sintering metal that quickly "wets" and dissolves the diamond or CBN and uses only as much metal as required to precipitate Diamond or PCBN particle-to-particle bonding. Whereas in a "premixed" environment the metal "blinds off" the particle-to particle reaction because too much metal is present, or conversely, not  
15 enough metal is present to ensure the optimal reaction.

Furthermore, it is felt that the "wave front" of metal sweeping through the powder matrix also carries away impurities that would otherwise impede the formation of high quality PDC or PCBN. These impurities are normally "pushed" ahead of the sintering metal "wave front" and are deposited in pools adjacent to the  
20 refractory containment cans. Figure 19 depicts the substrate 1904, the wavefront 1903, and the feedstock crystals or powder 1902 which the wavefront will sweep through 1901. Certain refractory material such as Niobium, Molybdenum, and Zirconium can act as "getters" which combine with the impurities as they immerge from the matrix giving additional assistance in the creation of high quality end  
25 products.

While there are compelling reasons to use the "sweep" process in sintering PDC and PCBN there are also problems that arise out of its use. For example, not all substrate metals are as controllable as others as to the quantity of material that is delivered and ultimately utilized by the powder matrix during sintering. Cobalt metal  
30 (6 to 13% by volume) sweeping from cemented tungsten carbide is very controllable when used against diamond or PCBN powders ranging from 1 to 40 microns particle sized. On the other hand, Cobalt Chrome Molybdenum (CoCrMo) that is useful as a solvent metal to make PDC for some applications overwhelms the same PDC matrix with CoCrMo metal in a pure sweep process sometimes producing inferior quality  
35 PDC. The fact that the CoCrMo has a lower melting point than cobalt, and further that there is an inexhaustible supply when using a solid CoCrMo substrate adjacent to the PDC matrix, creates a non-controllable processing condition.

In some applications where it is necessary to use sintering metals such a CoCrMo that can not be "swept" from a cemented carbide product, it is necessary to provide a simulated substrate against the PDC powders that provides a controlled release and limited supply of CoCrMo for the process.

5        These "simulated" substrates have been developed in the forms of "gradient" layers of mixtures of diamond, carbides, and metals to produce the desired "sweep" affect for sintering the outer layer of PDC. The first "gradient layer" (just adjacent to the outer or primary diamond layer which will act as the bearing or wear surface) can be prepared using a mixture of Diamond,  $\text{Cr}_3\text{C}_2$ , and CoCrMo. Depending of the size  
10        fraction of the diamond powder used in the outer layer, the first gradient layers diamond size fraction and metal content is adjusted for the optimal sintering conditions.

Where a "simulated" substrate is used, it has been discovered that often a small amount of solvent metal, in this case CoCrMo must be added to the outside  
15        diamond layer as catalyst to "kick-off" the sintering reaction.

One embodiment utilizes the mix ranges for the outer 2001 and Inner 2002 gradient layers of Figure 20 that are listed in Table 9.

TABLE 9

20

GRADIANT LAYERS	DIAMOND (Vol. Percent)	DIAMOND (Size Fraction- $\mu\text{m}$ )	$\text{Cr}_3\text{C}_2$ (Vol. Percent)	CoCrMo (Vol. Percent)
Outer	92	25	0	8
Inner	70	40	10	20

The use of gradient layers with solid layers of metal allows the designer to match the Bulk Modulus to the Coefficient of Thermal Expansion (CTE) of various  
25        features of the construct to counteract dilatory forces encountered during the HTHP phase of the sintering process. For example, in a spherical construct as the pressure increases the metals in the construct are compressed or dilated radially toward the center of the sphere. Conversely, as the sintering temperature increases the metal expands radially away from the center of the sphere. Unless these forces are  
30        balanced in some way, the compressive dilatory forces will initiate cracks in the outer diamond layer and cause the construct to be unusable.

Typically, changes in bulk modulus of solid metal features in the construct are controlled by selecting metals with a compatible modulus of elasticity. The thickness



and other sizing features are also important. CTE, on the other hand, is changed by the addition of diamond or other carbides to the gradient layers.

One embodiment, depicted in Figure 21, involves the use of two gradient outer layers 2101 and 2102, a solid titanium layer 2103 and an inner CoCrMo sphere 2104. In this embodiment the first gradient layer provides a "sweep source" of biocompatible CoCrMo solvent metal to the outer diamond layer. The solid Titanium layer provides a dilatory source that offsets the CTE from the solid CoCrMo center ball and keeps it from "pulling away" from the Titanium/CoCrMo interface as the sintering pressure and temperature go from the 65Kbar and 1400 °C sintering range to 1bar and room temperature.

Where two or more powder based gradient layers are to be used in the construct it becomes increasingly important to control the CTE of each layer to ensure structural integrity following sintering. During the sintering process stresses are induced along the interface between each of the gradient layers. These high stresses are a direct result of the differences in the CTE between any two adjacent layers. To reduce these stresses one or both of the layer materials CTE's must be modified.

The CTE of the a substrate can be modified by either changing to a substrate with a CTE close to that of diamond (an example is the use of cemented Tungsten Carbide, where the CTE of Diamond is approximately  $1.8 \mu\text{m/m-}^{\circ}\text{C}$  and Cemented Tungsten Carbide is Approximately  $4.4 \mu\text{m/m-}^{\circ}\text{C}$ ), or in the case of powdered layers, by adding a low CTE material to the substrate layer itself. That is, making a mixture of two or more materials, one or more of which will alter the CTE of the substrate layer.

Metal powders can be mixed with diamond or other superhard materials to produce a material with a CTE close to that of diamond and thus produce stresses low enough following sintering to prevent delamination of the layers at their interfaces. Experimental data shows that the CTE altering materials will not generally react with each other, which allows the investigator to predict the outcome of the intermediate CTE for each gradient level.

The desired CTE is obtained by mixing specific quantities of two materials according to the rule of mixtures. Table10 shows the change in CTE between two materials, A and B as a function of composition (Volume Percent). In this example, materials A and B have CTE's of 150 and 600  $\mu\text{in./in. -}^{\circ}\text{F}$  respectively. By adding 50 mol % of A to 50 mol % of B the resulting CTE is 375  $\mu\text{in./in. -}^{\circ}\text{F}$ .

One or more of the following component processes is incorporated into the mold release system:

- 1) An intermediate layer of material between the polycrystalline diamond compact part and the mould that prevents bonding of the polycrystalline diamond compact to the mould surface.
- 2) A mold material that does not bond to the polycrystalline diamond compact under the conditions of synthesis.
- 3) A mold material that, in the final stages of, or at the conclusion of, the polycrystalline diamond compact synthesis cycle either contracts away from the polycrystalline diamond compact in the case of a net concave polycrystalline diamond compact geometry, or expands away from the polycrystalline diamond compact in the case of a net convex polycrystalline diamond compact geometry.
- 4) The mold shape can also act, simultaneously as a source of sweep metal useful in the polycrystalline diamond compact synthesis process.

As an example, a mold release system may be utilized in manufacturing a polycrystalline diamond compact by employing a negative shape of the desired geometry to produce hemicon-planar parts. The mold surface contracts away from the final net concave geometry, the mold surface acts as a source of solvent-catalyst metal for the polycrystalline diamond compact synthesis process, and the mold surface has poor bonding properties to polycrystalline diamond compacts.

Table 10

PREDICTED DIMENSIONAL CHANGES IN AN EIGHT INCH LAYERED CONSTRUCT

A %	B%	CTE ( $\mu$ In. / In- $^{\circ}$ F)	Total Length Change (In.)	Final Dimension (In.)
100	0	150	.0012	7.9988
90	10	195	.0016	7.9984
80	20	240	.0019	7.9981
70	30	285	.0023	7.9977
60	40	330	.0026	7.9974
50	50	375	.0030	7.9970
40	60	420	.0034	7.9966
30	70	465	.0037	7.9963
20	80	510	.0041	7.9959
10	90	555	.0044	7.9956
0	100	600	.0048	7.9952

Referring to Figure 22, an illustration of how the above CTE modification works in a one-dimensional example. The one-dimensional example works as well in a three-dimensional construct. If the above materials A and B are packed in alternating layers 2201 and 2202 as shown in Figure 22, separately in their pure forms, with their CTE's of 150 and 600  $\mu$  In./In.  $-^{\circ}$ F respectively, they will contract exactly 150  $\mu$  In./In.  $-^{\circ}$ F and 600  $\mu$  In./In.  $-^{\circ}$ F for every degree decrease in temperature. For an eight inch block of the one inch thick stacked layers the total change in dimension for a one degree decrease in temperature will be:

$$\text{Material A: } (4 \times 1\text{In.}) \times (.00015 \text{ In. / In. } -^{\circ}\text{F}) \times 1^{\circ}\text{F} = .0006 \text{ In.}$$

$$\text{Material B: } (4 \times 1\text{In.}) \times (.00060 \text{ In. / In. } -^{\circ}\text{F}) \times 1^{\circ}\text{F} = \underline{.0024 \text{ In.}}$$

$$\text{Total overall length decrease in eight inches} = .0030 \text{ In.}$$

By comparison, each of the layers is modified by using a mixture of 50% of A and 50% of B, and all eight layers are stacked into the eight-inch block configuration shown in Fig. 7. Re-calculation of the overall length decrease using the new composite CET of 375  $\mu$  In./In.  $-^{\circ}$ F from Table II shows:

$$\text{Material A + B: } (8 \times 1\text{In.}) \times (.000375 \text{ In. / In. } -^{\circ}\text{F}) \times 1^{\circ}\text{F} = .0030 \text{ In.}$$

$$\text{Total overall length decrease in eight inches} = .0030 \text{ In.}$$

The length decrease in this case was accurately predicted for the one-dimensional construct using one-inch thick layers by using the Rule of Mixtures.

Metals have very high CTE values as compared to diamond, which has one of the lowest CTE's of any known material. When metals are used as substrates for PDC and PCBN sintering considerable stress is developed at the interface. Therefore, mixing low CTE material with the biocompatible metal for medical implants can be used to reduce interfacial stresses. One of the best candidate materials is diamond itself. Other materials include refractory metal carbides and bitrides, and some oxides. Borides and silicides would also be good materials from a theoretical standpoint, but may not be biocompatible. The following is a list of candidate materials:

Carbides	Silicides	Oxynitrides
Nitrides	Oxides	
Oxyborides		
Borides	Oxycarbides	
Carbonitrides		

There are other materials and combinations of materials that could be utilized as CTE modifiers.

There are also other factors that also apply to the reduction of interface stresses for a particular geometrical construct. The thickness of the gradient layer, its position in the construct, and the general shape of the final construct all contribute in interfacial stress tensor reduction. Geometries that are more spherical tend to promote interface circumferential failures from positive or negative radial tensors while geometries of a cylindrical configuration tend to fail at the layer interfaces precipitated by bending stress couples.

The design of the gradient layers respecting CTE and the amount of contraction the each individual layer will experience during cooling from the HTHP sintering process will largely dictate the direction of stress tensors in the construct. Generally, the designer will always desire to have the outer wear layer of superhard material in compression to prevent delamination and crack propagation. In spherical geometries the stress tensors would be directed radially toward the center of the spherical shape giving special attention to the interfacial stresses at each layer interface to prevent failures at these interfaces as well. In cylindrical geometries the stress tensors would be adjusted to prevent stress couples from initiating cracks in either end of the cylinder, especially at the end where the wear surface is present.

The following are embodiments that relates to a spherical geometry wherein combinations of gradient layers and/or solid metal balls are used to control the final outcomes of the constructs. Figure 23 is an embodiment that shows a spherical construct, which utilizes five gradient layers wherein the composition of each layer is described in Tables 11 and 12:

TABLE 11

LAYER	DIAMOND		Cr3C2	CoCrMo	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	
First (Outer Layer) 2301	20	92	8	0	.090
Second 2302	40	70	20	20	.104
Third 2303	70	60	20	20	.120
Forth 2304	70	60	26	26	.138
Fifth 2305	70	25	37.5	37.5	.154

TABLE 12

LAYER	DIAMOND		Cr3C2	CoCrMo	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	
First (Outer Layer) 2301	20	100	0	0	.090
Second 2302	40	70	20	20	.104
Third 2304	70	60	20	20	.120
Forth 2304	70	60	26	26	.138
Fifth 2305	70	25	37.5	37.5	.154

Figure 24 is an embodiment that shows a spherical construct, which utilizes four gradient layers wherein the composition of each layer is described in Tables 13 and 14.

TABLE 13

LAYER	DIAMOND		Cr3C2	CoCrMo	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	
First (Outer Layer) 2401	20	92	0	8	.097
Second 2402	40	70	10	20	.125
Third 2403	70	60	20	20	.144
Forth 2404	70	50	25	25	.240

TABLE 14

LAYER	DIAMOND		Cr3C2	CoCrMo	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	
First (Outer Layer) 2401	20	100	0	0	.097
Second 2402	40	70	10	20	.125
Third 2403	70	60	20	20	.144
Forth 2404	70	50	25	25	.240

10

Figure 25 shows an embodiment construct that utilizes a center support ball with gradient layers laid up on the ball and each other to form the complete construct. The inner ball of solid metal CoCrMo is encapsulate with a .003 to .010 inch thick refractory barrier can to prevent the over saturation of the system with the ball metal

during the HTHP phase of sintering. The composition of each layer is described in Tables 15 and 16.

TABLE 15

LAYER	DIAMOND		Cr <sub>3</sub> C <sub>2</sub> Volume %	CoCrMo Volume %	LAYER THICKNESS (In.)
	Size (μ m)	Volume %			
First (Outer Layer) 2501	20	92	0	8	.097
Second 2502	40	70	10	20	.125
Third 2503	70	60	20	20	.144
CoCrMo Ball 2504	N/A	N/A	N/A	N/A	N/A

5

TABLE 16

LAYER	DIAMOND		Cr <sub>3</sub> C <sub>2</sub> Volume %	CoCrMo Volume %	LAYER THICKNESS (In.)
	Size (μ m)	Volume %			
First (Outer Layer) 2501	20	100	0	0	.097
Second 2502	40	70	10	20	.125
Third 2503	70	60	20	20	.144
CoCrMo Ball 2504	N/A	N/A	N/A	N/A	N/A

Predicated on the end use function of the sphere above, the inner ball could be made of Cemented Tungsten Carbide, Niobium, Nickel, Stainless steel, Steel, or one of several other metal or ceramic materials to suite the designers needs.

10

Embodiments relating to dome shapes are described as follow:

Figure 26 shows a dome embodiment construct that utilizes two gradient layers 2601 and 2602 wherein the composition of each layer is described in Tables 17 and 18.

15

TABLE 17

LAYER	DIAMOND		Cr <sub>3</sub> C <sub>2</sub> Volume %	CoCrMo Volume %	TiC/TiN Volume %	LAYER THICKNESS (In.)
	Size (μ m)	Volume %				
First (Outer Layer)	20	94	0	6	0.05	.200

2602						
Second 2601	70	60	20	20	0.05	.125

TABLE 18

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	
First (Outer Layer) 2602	20	100	0	0	0.05	.200
Second 2601	70	60	20	20	0.05	.125

- 5 Figure 27 shows a dome embodiment construct that utilizes two gradient layers 2701 and 2702 wherein the composition of each layer is described in Tables 19 and 20:

TABLE 19

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	
First (Outer Layer) 2702	20	94	0	6	0.05	.128
Second 2701	70	60	20	20	0.05	.230

10

TABLE 20

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	
First (Outer Layer) 2702	20	100	0	0	0.05	.128
Second 2701	70	60	20	20	0.05	.230

- Figure 28 shows a dome embodiment construct that utilizes three gradient layers 2801, 2802 and 2803 where the composition of each layer is described in Tables 21 and 22:
- 15

TABLE 21

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	

First (Outer Layer) 2801	20	96	0	4	0.05	.168
Second 2802	40	80	10	10	0.05	.060
Third 2803	70	60	20	20	0.05	.130

TABLE 22

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 2801	20	100	0	0	0.05	.168
Second 2802	40	80	10	10	0.05	.060
Third 2803	70	60	20	20	0.05	.130

Figure 29 shows a dome embodiment construct that utilizes three gradient layers  
 5 2901, 2902 and 9803 wherein the composition of each layer is described in Tables  
 23 and 24:

TABLE 23

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 2901	20	96	0	4	0.05	.065
Second 2902	40	80	10	10	0.05	.050
Third 2903	70	60	20	20	0.05	.243

10

TABLE 24

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNES S (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 2901	20	100	0	0	0.05	.065
Second 2902	40	80	10	10	0.05	.050
Third 2903	70	60	20	20	0.05	.243

Embodiments relating to Flat Cylindrical shapes are described as follows:

15



Figure 30 shows a flat cylindrical embodiment construct that utilizes two gradient layers 3001 and 3002 wherein the composition of each layer is described in Tables 25 and 26:

5 TABLE 25

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3001	20	94	0	6	0.05	
Second 3002	70	60	20	20	0.05	

TABLE 26

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3001	20	100	0	0	0.05	
Second 3002	70	60	20	20	0.05	

10 Figure 31 shows a flat cylindrical embodiment construct that utilizes three gradient layers 3101, 3102, 3103 wherein the composition of each layer is described in Tables 27 and 28:

TABLE 27

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3101	20	96	0	4	0.05	
Second 3102	40	80	10	10	0.05	
Third 3103	70	60	20	20	0.05	

15

TABLE 28

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNES S (In.)
	Size ( $\mu$ m)	Volume %				

First (Outer Layer) 3101	20	100	0	0	0.05	
Second 3102	40	80	10	10	0.05	
Third 3103	70	60	20	20	0.05	

Figure 32 shows a flat cylindrical embodiment construct that utilizes three gradient layers 3201, 3202, 3203 laid up on a CoCrMo substrate 3204. The cylindrical substrate of solid metal CoCrMo is encapsulate with a .003 to .010 inch thick refractory barrier can 3205 to prevent the over saturation of the system with the substrate metal during the HTHP phase of sintering. The composition of each layer is described in Tables 29 and 30:

10 TABLE 29

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3201	20	96	0	4	0.05	
Second 3202	40	80	10	10	0.05	
Third 3203	70	60	20	20	0.05	
CoCrMo Substrate 3204	N/A	N/A	N/A	N/A	N/A	

TABLE 30

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3201	20	100	0	0	0.05	
Second 3202	40	80	10	10	0.05	
Third 3203	70	60	20	20	0.05	
CoCrMo Substrate 3204	N/A	N/A	N/A	N/A	N/A	

15 Predicated on the end use function of the cylinder shape of Figure 32 the inner substrate could be made of Cemented Tungsten Carbide, Niobium, Nickel, Stainless steel, Steel, or one of several other metal or ceramic materials to suite the designers needs.

Embodiments relating to Flat Cylindrical Shapes with Formed-in-Place Concave Features are described as follow:

- 5 Figure 33 show an embodiment of a flat cylindrical shape with a formed in place concave trough 3303 that utilizes two gradient layers 3301 and 3302 wherein the composition of each layer is described in Tables 31 and 32:

TABLE 31

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	
First (Outer Layer) 3301	20	94	0	6	0.05	.156
Second 3302	70	60	20	20	0.05	.060
Filler Support 3303	70	60	20	20	0.05	N/A

10

TABLE 32

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	
First (Outer Layer) 3301	20	100	0	0	0.05	.156
Second 3302	70	60	20	20	0.05	.060
Filler Support 3303	70	60	20	20	0.05	N/A

- 15 Figure 34 shows an embodiment of a flat cylindrical shape with a formed in place concave trough 3402 that utilizes two gradient layers 3401 and 3402 wherein the composition of each layer is described in Tables 33 and 34:

TABLE 33

LAYER	DIAMOND		Cr3C2	CoCrMo	TiCTiN	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %	Volume %	Volume %	Volume %	
First (Outer Layer) 3401	20	94	0	6	0.05	.156
Second 3402	70	60	20	20	0.05	.060
Filler Support 3403	70	60	20	20	0.05	N/A

TABLE 34

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3401	20	100	0	0	0.05	.156
Second 3402	70	60	20	20	0.05	.060
Filler Support 3403	70	60	20	20	0.05	N/A

Figure 35 shows an embodiment of a flat cylindrical shape with a formed in place concave 3504 trough that utilizes three gradient layers 3501, 3502, 2503 wherein the composition of each layer is described in Tables 35 and 36:

TABLE 35

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3501	20	96	0	4	0.05	.110
Second 3502	40	80	10	10	0.05	.040
Third 2503	70	60	20	20	0.05	.057
Filler Support 3504	70	60	20	20	0.05	N/A

TABLE 36

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3501	20	100	0	0	0.05	.110
Second 3502	40	80	10	10	0.05	.040
Third 3503	70	60	20	20	0.05	.057
Filler Support 3504	70	60	20	20	0.05	N/A

10

Figure 36 shows an embodiment of a flat cylindrical shape with a formed in place concave trough 3604 that utilizes three gradient layers 3601, 3602, 3603 wherein the composition of each layer is described in Tables 37 and 38:

TABLE 37

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3601	20	96	0	4	0.05	.110
Second 3602	40	80	10	10	0.05	.040
Third 3603	70	60	20	20	0.05	.057
Filler Support 3604	70	60	20	20	0.05	N/A

TABLE 38

LAYER	DIAMOND		Cr3C2 Volume %	CoCrMo Volume %	TiCTiN Volume %	LAYER THICKNESS (In.)
	Size ( $\mu$ m)	Volume %				
First (Outer Layer) 3601	20	100	0	0	0.05	.110
Second 3602	40	80	10	10	0.05	.040
Third 3603	70	60	20	20	0.05	.057
Filler Support 3604	70	60	20	20	0.05	N/A

5

### Prepare Heater Assembly

In order to sinter the assembled and loaded diamond feedstock described above into polycrystalline diamond, both heat and pressure are required. Heat is provided electrically as the part undergoes pressure in a press. A heater assembly is used to provide the required heat.

A refractory metal can containing loaded and precompressed diamond feedstock is placed into a heater assembly. Salt domes are used to encase the can. The salt domes used may be white salt (NaCl) that is precompressed to at least about 90- 95% of theoretical density. This density of the salt is desired to preserve high pressures of the sintering system and to maintain geometrical stability of the manufactured part. The salt domes and can are placed into a graphite heater tube assembly. The salt and graphite components of the heater assembly may be baked in a vacuum oven at greater than 100 degrees Celsius and at a vacuum of at least 23 torr for about 1 hour in order to eliminate adsorped water prior to loading in the heater assembly . Other materials which may be used in construction of a heater assembly include solid or foil graphite, amorphous carbon, pyrolytic carbon, refractory metals and high electrical resistant metals.

Once electrical power is supplied to the heater tube, it will generate heat

required for polycrystalline diamond formation in the high pressure/high temperature pressing operation.

#### Preparation of Pressure Assembly for Sintering

Once a heater assembly has been prepared, it is placed into a pressure  
5 assembly for sintering in a press under high pressure and high temperature. A cubic  
press or a belt press may be used for this purpose, with the pressure assembly  
differing somewhat depending on the type of press used. The pressure assembly is  
intended to receive pressure from a press and transfer it to the diamond feedstock so  
that sintering of the diamond may occur under isostatic conditions.

10 If a cubic press is used, then a cube of suitable pressure transfer media such  
as pyrophillite will contain the heater assembly. Cell pressure medium would be  
used if sintering were to take place in a belt press. Salt may be used as a pressure  
transfer media between the cube and the heater assembly. Thermocouples may be  
used on the cube to monitor temperature during sintering. The cube with the heater  
15 assembly inside of it is considered a pressure assembly, and is placed into a press a  
press for sintering.

#### Sintering of Feedstock into Polycrystalline Diamond

The pressure assembly described above containing a refractory metal can  
that has diamond feedstock loaded and precompressed within is placed into an  
20 appropriate press. The type of press used at the time of the devices may be a cubic  
press (i.e., the press has six anvil faces) for transmitting high pressure to the  
assembly along 3 axes from six different directions. Alternatively, a belt press and a  
cylindrical cell can be used to obtain similar results. Other presses may be used as  
well. Referring to Figure 37, a representation of the 6 anvils of a cubic press 3720 is  
25 provided. The anvils 3721, 3722, 3723, 3724, 3725 and 3726 are situated around a  
pressure assembly 3730.

To prepare for sintering, the entire pressure assembly is loaded into a press  
and initially pressurized to about 40-68 Kbars. The pressure to be used depends on  
the product to be manufactured and must be determined empirically. Then electrical  
30 power may be added to the pressure assembly in order to reach a temperature in the  
range of less than about 1145 or 1200 to more than about 1500 degrees Celsius.  
About 5800 watts of electrical power may be used at two opposing anvil faces,  
creating the current flow required for the heater assembly to generate the desired  
level of heat. Once the desired temperature is reached, the pressure assembly is  
35 subjected to pressure of about 1 million pounds per square inch at the anvil face.  
The components of the pressure assembly transmit pressure to the diamond  
feedstock. These conditions may be maintained for about 3-12 minutes, but could be  
from less than 1 minute to more than 30 minutes. The sintering of polycrystalline

diamond compacts takes place in an isostatic environment where the pressure transfer components are permitted only to change in volume but are not permitted to otherwise deform. Once the sintering cycle is complete, about a 90 second cool down period is allowed, and then pressure is removed. The polycrystalline diamond compact is then removed for finishing.

Removal of a sintered polycrystalline diamond compact having a curved, compound or complex shape from a pressure assembly is simple due to the differences in material properties between diamond and the surrounding metals in some embodiments of the devices. This is generally referred to as the mold release system of the devices.

#### Removal of Solvent-Catalyst Metal from PCD

If desired, the solvent-catalyst metal remaining in interstitial spaces of the sintered polycrystalline diamond may be removed. Such removal is accomplished by chemical leaching as is known in the art. After solvent-catalyst metal has been removed from the interstitial spaces in the diamond table, the diamond table will have greater stability at high temperatures. This is because there is no catalyst for the diamond to react with and break down.

After leaching solvent-catalyst metal from the diamond table, it may be replaced by another metal, metal or metal compound in order to form thermally stable diamond that is stronger than leached polycrystalline diamond. If it is intended to weld synthetic diamond or a polycrystalline diamond compact to a substrate or to another surface such as by inertia welding, it may be desirable to use thermally stable diamond due to its resistance to heat generated by the welding process.

#### Finishing Methods and Apparatuses

Once a polycrystalline diamond compact has been sintered, a mechanical finishing process may be employed to prepare the final product. The finishing steps explained below are described with respect to finishing a polycrystalline diamond compact, but they could be used to finish any other surface or any other type of component.

Prior to the devices herein, the synthetic diamond industry was faced with the problem of finishing flat surfaces and thin edges of diamond compacts. Methods for removal of large amounts of diamond from non-planar surfaces or finishing those surfaces to high degrees of accuracy for sphericity, size and surface finish had not been developed in the past.

#### Finishing of Superhard Cylindrical and Flat Forms.

In order to provide a greater perspective on finishing techniques for curved and non-planar superhard surfaces for articulating diamond-surfaced spinal implants, a description of other finishing techniques is provided.

### Lapping.

A wet slurry of diamond grit on cast iron or copper rotating plates are used to remove material on larger flat surfaces (e.g., up to about 70 mm. in diameter). End coated cylinders of size ranging from about 3 mm to about 70 mm may also be  
5 lapped to create flat surfaces. Lapping is generally slow and not dimensionally controllable for depth and layer thickness, although flatness and surface finishes can be held to very close tolerances.

### Grinding.

Diamond impregnated grinding wheels are used to shape cylindrical and flat  
10 surfaces. Grinding wheels are usually resin bonded in a variety of different shapes depending on the type of material removal required (i.e., cylindrical centerless grinding or edge grinding). Polycrystalline diamond compacts are difficult to grind, and large polycrystalline diamond compact surfaces are nearly impossible to grind. Consequently, it is desirable to keep grinding to a minimum, and grinding is usually  
15 confined to a narrow edge or perimeter or to the sharpening of a sized PDC end-coated cylinder or machine tool insert.

### Electro Spark Discharge Grinding (EDG).

Rough machining of polycrystalline diamond compact may be accomplished with electro spark discharge grinding ("EDG") on large diameter (e.g., up to about 70  
20 mm.) flat surfaces. This technology typically involves the use of a rotating carbon wheel with a positive electrical current running against a polycrystalline diamond compact flat surface with a negative electrical potential. The automatic controls of the EDG machine maintain proper electrical erosion of the polycrystalline diamond compact material by controlling variables such as spark frequency, voltage and  
25 others. EDG is typically a more efficient method for removing larger volumes of diamond than lapping or grinding. After EDG, the surface must be finish lapped or ground to remove what is referred to as the heat affected area or re-cast layer left by EDG.

### Wire Electrical Discharge Machining (WEDM).

30 WEDM is used to cut superhard parts of various shapes and sizes from larger cylinders or flat pieces. Typically, cutting tips and inserts for machine tools and re-shaping cutters for oil well drilling bits represent the greatest use for WEDM in PDC finishing.

### Polishing.

35 Polishing superhard surfaces for articulating diamond-surfaced spinal implants to very high tolerances may be accomplished by diamond impregnated high speed polishing machines. The combination of high speed and high friction temperatures tends to burnish a PDC surface finished by this method, while



maintaining high degrees of flatness, thereby producing a mirror-like appearance with precise dimensional accuracy.

b. Finishing A Non-planar Geometry.

Finishing a non-planar surface (concave non-planar or convex non-planar) presents a greater problem than finishing a flat surface or the rounded edge of a cylinder. The total surface area of a sphere to be finished compared to the total surface area of a round end of a cylinder of like radius is four (4) times greater, resulting in the need to remove four (4) times the amount of polycrystalline diamond compact material. The nature of a non-planar surface makes traditional processing techniques such as lapping, grinding and others unusable because they are adapted to flat and cylindrical surfaces. The contact point on a sphere should be point contact that is tangential to the edge of the sphere, resulting in a smaller amount of material removed per unit of time, and a proportional increase in finishing time required. Also, the design and types of processing equipment and tooling required for finishing non-planar objects must be more accurate and must function to closer tolerances than those for other shapes. Non-planar finishing equipment also requires greater degrees of adjustment for positioning the workpiece and tool ingress and egress.

The following are steps that may be performed in order to finish a non-planar, rounded or arcuate surface.

1.) Rough Machining.

Initially roughing out the dimensions of the surface using a specialized electrical discharge machining apparatus may be performed. Referring to Figure 38, roughing a polycrystalline diamond compact sphere 3803 is depicted. A rotator 3802 is provided that is continuously rotatable about its longitudinal axis (the z axis depicted). The sphere 3803 to be roughed is attached to a spindle of the rotator 3802. An electrode 3801 is provided with a contact end 3801A that is shaped to accommodate the part to be roughed. In this case the contact end 3801A has a partially non-planar shape. The electrode 3801 is rotated continuously about its longitudinal axis (the y axis depicted). Angular orientation of the longitudinal axis y of the electrode 3801 with respect to the longitudinal axis z of the rotator 3802 at a desired angle  $\beta$  is adjusted to cause the electrode 3801 to remove material from the entire non-planar surface of the ball 3803 as desired.

Thus, the electrode 3801 and the sphere 3803 are rotating about different axes. Adjustment of the axes can be used to achieve near perfect non-planar movement of the part to be roughed. Consequently, a nearly perfect non-planar part results from this process. This method produces polycrystalline diamond compact non-planar surfaces with a high degree of sphericity and cut to very close tolerances. By controlling the amount of current introduced to the erosion process, the depth and

amount of the heat affected zone can be minimized. In the case of a polycrystalline diamond compact, the heat affected zone can be kept to about 3 to 5 microns in depth and is easily removed by grinding and polishing with diamond impregnated grinding and polishing wheels.

5 Referring to Figure 39, roughing a convex non-planar polycrystalline diamond compact 1003 such as an articulating diamond-surfaced spinal implant is depicted. A rotator 3902 is provided that is continuously rotatable about its longitudinal axis (the z axis depicted). The part 3903 to be roughed is attached to a spindle of the rotator 3902. An electrode 3901 is provided with a contact end 3901A that is shaped to  
10 accommodate the part to be roughed. The electrode 3901 is continuously rotatable about its longitudinal axis (the y axis depicted). Angular orientation of the longitudinal axis y of the electrode 3901 with respect to the longitudinal axis z of the rotator 3902 at a desired angle  $\beta$  is adjusted to cause the electrode 3901 to remove material from the entire non-planar surface of the articulating diamond-surfaced spinal implant  
15 3903 as desired.

In some embodiments of the devices, multiple electro discharge machine electrodes will be used in succession in order to machine a part. A battery of electro discharge machines may be employed to carry this out in assembly line fashion. Further refinements to machining processes and apparatuses are described below.

20 Complex positive or negative relief (concave or convex) forms can be machined into Polycrystalline Diamond Compacts (PDC) or Polycrystalline cubic Boron Nitride (PCBN) parts. This a standard Electrical Discharge Machining (EDM) CNC machining center and suitably machined electrodes accomplish the desired forms.

25 Figure 40 (side view) and Figure 40a (end view) show an electrode 4001 with a convex form 4002 machined on the active end of the electrode 4001, and the electrode base 4005. Figure 41 (cross section at 41-41) and Figure 41a show an electrode 4101 with a concave form 4102 and base 4105. The opposite ends of the electrodes are provided with an attachment mechanism at the base 4105 suitable for  
30 the particular EDM machine being utilized. There are a variety of electrode materials that can be utilized such a copper, copper tungsten, graphite, and combinations of graphite and metal mixes. Materials best suited for machining PDC and PCBN are copper tungsten for roughing and pure graphite, or graphite copper tungsten mixes. Not all EDM machines are capable of machining PDC and PCBN. Only those  
35 equipped with capacitor discharge power supplies can generate spark intensities with enough power to efficiently erode these materials.

The actual size of the machined relief form is usually machined undersized to allow for a suitable spark gap for the burning/erosion process to take place. Each

spark gap length dictates a set of machining parameters that must be set by the machine operator to ensure efficient electrical discharge erosion of the material to be removed. Normally, two to four electrodes are prepared with different spark gap allowances. For example, an electrode using a .006 in. spark gap could be prepared for "roughing," and an "interim" electrode at .002 in. spark gap, and "finishing" electrode at .0005 in. spark gap. In each case the machining voltage (V), peak amperage (AP), pulse duration (P), reference frequency (RF), pulse duration (A), retract duration (R), under-the-cut duration (U), and servo voltage (SV) must be set up within the machines control system.

Figure 42 shows an EDM relief form 4201 sinking operation in a PDC insert part 4202. Table 39 describes the settings for the using a copper tungsten electrode 4203 for roughing and a graphite/copper tungsten electrode for finishing. The spark gap 4204 is also depicted.

**TABLE 39**

Electrode 4203	Spark Gap 4204	V	AP	P	RF	A	R	U	SV
<b>Roughing</b>	.006	-2	7	13	56	9	0	9	50
<b>Finishing</b>	.001	-5	4	2	60	2	0	9	55

Those familiar with the field of EDM machining will recognize that variations in the parameters show will be required based on the electrode configuration, electrode wear rates desired, and surface finishes required. Generally, higher machining rates, i.e., higher values of "V" and "AP" produce higher rates of discharge erosion, but conversely rougher surface finishes.

Obtaining very smooth and accurate finishes also requires the use of a proper dielectric machining fluid. Synthetic hydrocarbons with satellite electrodes as disclosed in United States Patent No. 5,773,782, which is hereby incorporated by reference, appear to assist in obtaining high quality surface finishes.

Figure 43 shows an embodiment wherein a single ball-nosed (spherical radiused) EDM electrode 4301 is used to form a concave relief form 4303 in a PDC or PCBN part 4302. The electrode 4301 is plunged vertically into the part 4302 and then moved laterally to accomplish the rest of the desired shape. By programming a CNC system EDM electrode "cutting path" of the EDM machine, an infinite variety of concave or convex shapes can be machined. Controlling the rate of "down" plunging

and "lateral" cross cutting, and using the correct EDM material will dictate the quality of the size dimensions and surface finishes obtained.

## 2.) Finish Grinding and Polishing.

Once the non-planar surface (whether concave or convex) has been rough  
5 machined as described above or by other methods, finish grinding and polishing of a part can take place. Grinding is intended to remove the heat affected zone in the polycrystalline diamond compact material left behind by electrodes.

In some embodiments of the devices, grinding utilizes a grit size ranging from 100 to 150 according to standard ANSI B74.16-1971 and polishing utilizes a grit size  
10 ranging from 240 to 1500, although grit size may be selected according to the user's preference. Wheel speed for grinding should be adjusted by the user to achieve a favorable material removal rate, depending on grit size and the material being ground. A small amount of experimentation can be used to determine appropriate wheel speed for grinding. Once the spherical surface (whether concave or convex)  
15 has been rough machined as described above or by other methods, finish grinding and polishing of a part can take place. Grinding is intended to remove the heat affected zone in the polycrystalline diamond compact material left behind by electrodes. Use of the same rotational geometry as depicted in Figures 9 and 10 allows sphericity of the part to be maintained while improving its surface finish  
20 characteristics.

Referring to Figure 44, it can be seen that a rotator 4401 holds a part to be finished 4403, in this case a convex sphere, by use of a spindle. The rotator 4401 is rotated continuously about its longitudinal axis (the z axis). A grinding or polishing wheel 4402 is provided is rotated continuously about its longitudinal axis (the x axis).  
25 The moving part 4403 is contacted with the moving grinding or polishing wheel 4402. The angular orientation  $\beta$  of the rotator 4401 with respect to the grinding or polishing wheel 4402 may be adjusted and oscillated to effect grinding or polishing of the part (ball or socket) across its entire surface and to maintain sphericity.

Referring to Figure 45, it can be seen that a rotator 4501 holds a part to be  
30 finished 4503, in this case a convex spherical cup or race, by use of a spindle. The rotator 4501 is rotated continuously about its longitudinal axis (the z axis). A grinding or polishing wheel 4502 is provided that is continuously rotatable about its longitudinal axis (the x axis). The moving part 4503 is contacted with the moving grinding or polishing wheel 4502. The angular orientation  $\beta$  of the rotator 4501 with  
35 respect to the grinding or polishing wheel 4502 may be adjusted and oscillated if required to effect grinding or polishing of the part across the spherical portion of it surface.

In one embodiment, grinding utilizes a grit size ranging from 100 to 150 according to standard ANSI B74.16-1971 and polishing utilizes a grit size ranging from 240 to 1500, although grit size may be selected according to the user's preference. Wheel speed for grinding should be adjusted by the user to achieve a favorable material removal rate, depending on grit size and the material being ground. A small amount of experimentation can be used to determine appropriate wheel speed for grinding.

As desired, a diamond abrasive hollow grill may be used for polishing diamond or superhard bearing surfaces. A diamond abrasive hollow grill includes a hollow tube with a diamond matrix of metal, ceramic and resin (polymer) is found.

If a diamond surface is being polished, then the wheel speed for polishing may be adjusted to cause a temperature increase or heat buildup on the diamond surface. This heat buildup will cause burnishing of the diamond crystals to create a very smooth and mirror-like low friction surface. Actual material removal during polishing of diamond is not as important as removal sub-micron sized asperities in the surface by a high temperature burnishing action of diamond particles rubbing against each other. A surface speed of 6000 feet per minute minimum is generally required together with a high degree of pressure to carry out burnishing. Surface speeds of 4000 to 10,000 feet per minute are believed to be the most desirable range. Depending on pressure applied to the diamond being polished, polishing may be carried out at from about 500 linear feet per minute and 20,000 linear feet per minute.

Pressure must be applied to the workpiece in order to raise the temperature of the part being polished and thus to achieve the most desired mirror-like polish, but temperature should not be increased to the point that it causes complete degradation of the resin bond that holds the diamond polishing wheel matrix together, or resin will be deposited on the diamond. Excessive heat will also unnecessarily degrade the surface of the diamond.

Maintaining a constant flow of coolant (such as water) across the diamond surface being polished, maintaining an appropriate wheel speed such as 6000 linear feet per minute, applying sufficient pressure against the diamond to cause heat buildup but not so much as to degrade the wheel or damage the diamond, and timing the polishing appropriately are all important and must all be determined and adjusted according to the particular equipment being used and the particular part being polished. Generally the surface temperature of the diamond being polished should not be permitted to rise above 800 degrees Celsius or excessive degradation of the diamond will occur. Desirable surface finishing of the diamond, called burnishing, generally occurs between 650 and 750 degrees Celsius.

During polishing it is important to achieve a surface finish that has the lowest possible coefficient of friction, thereby providing a low friction and long-lasting articulation surface. Preferably, once a diamond or other superhard surface is formed in a bearing component, the surface is then polished to an Ra value of 0.3 to 0.005 microns. Acceptable polishing will include an Ra value in the range of 0.5 to 0.005 microns or less. The parts of the bearing component may be polished individually before assembly or as a unit after assembly. Other methods of polishing polycrystalline diamond compacts and other superhard materials could be adapted to work with the articulation surfaces of the invented bearing components, with the objective being to achieve a smooth surface, preferably with an Ra value of 0.01-0.005 microns. Further grinding and polishing details are provided below.

Figure 46 shows a diamond grinding form 4601 mounted to an arbor 4602, which is in turn mounted into the high-speed spindle 4603 of a CNC grinding machine. The cutting path motion 4604 of the grinding form 4601 is controlled by the CNC program allowing the necessary surface coverage requiring grinding or polishing. The spindle speed is generally related to the diameter of the grinding form and the surface speed desired at the interface with the material 4505 to be removed. The surface speed should range between 4,000 and 17,000 feet per minuet for both grinding and polishing. For grinding, the basic grinding media for the grinding form should be as "free" cutting as practical with diamond grit sizes in the range of 80 to 120 microns and concentrations ranging from 75 to 125. For polishing the grinding media should not be as "free cutting," i.e., the grinding form should generally be harder and denser with grit sizes ranging from 120 to 300 microns and concentrations ranging from 100 to 150.

Superhard materials can be more readily removed by grinding if the actual area of the material being removed is kept as small as possible. Ideally the bruiting form 4601 should be rotated to create conditions in the range from 20,000 to 40,000 surface feet per minuet between the part 4605 and the bruiting form 4601. Spindle pressure between the part 4605 and the bruiting form 4601 operating in a range of 10 to 100 Lbs – force producing an interface temperature between 650 and 750 Deg C is required. Cooling water is needed to take away excess heat to keep the part from failing possible. The simplest way to keep the grind area small is to utilize a small cylindrical contact point (usually a ball form, although a radiused end of a cylinder accomplishes the same purpose), operating against a larger surface area.

Figures 47 shows the tangential area of contact 4620 between the grinding form 4601 and the substantially larger superhard material 4621. By controlling the path of the grinding form cutter, small grooves 4630 (Figure 48) can be ground into the surface of the superhard material 4621 removing the material and leaving small

“cusp” 4640 between the adjacent grooves. As the grooves are cut shallower and closer together the “cusp” 4640 become imperceptible to the naked eye and are easily removed by subsequent polishing operations. The cutter line path of the grinding form cutter should be controlled by programming the CNC system of the grinding machine to optimize the cusp size, grinding form cutter wear, and material removal rates.

#### Bruting

Obtaining highly polished surface finishes on Polycrystalline Diamond Compact (PDC), Polycrystalline Cubic Boron Nitride (PBCN), and other superhard materials in the range of 0.05 to 0.005  $\mu\text{m}$  can be obtained by running PDC form against the surface to be polished. “Bruting” or rubbing a diamond surface under high pressure and temperature against another superhard material degrades or burns away any positive asperities remaining from previous grinding and polishing operations producing a surface finish not obtainable in any other way.

Figure 49 shows a PDC dome part 4901 on a holder 4904 and being “Bruit Polished” using a PDC bruting form 4902 being rotated in a high-speed spindle 4903. Ideally the bruting form should be rotated in a range from 20,000 to 40,000 surface feet per minute with the spindle pressure operating in a range of 10 to 100 Lbs – force producing an interface temperature between 650 and 750 Deg C. Cooling water is generally required to take away excess heat to keep the part from failing.

Figure 50 shows another embodiment of the bruting polishing technique wherein the PDC Bruting form 5001 is controlled through a complex surface path 5002 by a CNC system of a grinding machine or a CNC Mill equipped with a high-speed spindle to control the point of contact 5003 of the form 5001 with a superhard component 5004.

#### USE OF COBALT CHROME MOLYBDENUM (CoCrMo) ALLOYS TO AUGMENT BIOCOMPATABILITY IN POLYCRYSTALLINE DIAMOND COMPACTS

Cobalt and Nickel may be used as catalyst metals for sintering diamond powder to produce sintered polycrystalline diamond compacts. The toxicity of both Co and Ni is well documented; however, use of CoCr alloys which contain Co and Ni have outstanding corrosion resistance and avoid passing on the toxic effects of Co or Ni alone. Use of CoCrMo alloy as a solvent-catalyst metal in the making of sintered polycrystalline diamond compacts yields a biocompatible and corrosion resistant material. Such alloys may be defined as any suitable biocompatible combination of the following metals: Co, Cr, Ni, Mo, Ti and W. Examples include ASTM F-75, F-799 and F-90. Each of these will serve as a solvent-catalyst metal when sintering diamond. Elemental analysis of the interstitial metal in PDC made with these alloys

has shown that the composition is substantially more corrosion resistant than PDC made with Co or Ni alone.

#### EXAMPLE ARTICULATING DIAMOND-SURFACED SPINAL IMPLANTS

As used herein, the term "articulating" means that the spinal implant permits  
5 some range of motion, in contrast with fusion therapy in which two vertebrae are permanently locked together with respect to each other. The spinal implants may provide rotation about the axial, coronal and/or sagittal axes and/or translation in the axial plane. The rotation may permit anterior and posterior bending, lateral bending, and twisting of the torso. The translation may include anterior, posterior and lateral  
10 translation. A combination of such rotation and translation is desired in order to approximate the flexion and extension of a human spine.

Also, as used herein "diamond-surfaced" means that the spinal implant includes diamond on at least a portion of one load bearing or articulation surface. The implant may include diamond located on a substrate, it may be solid free-  
15 standing diamond, or it may be of another structure. The diamond may be sintered polycrystalline diamond that is a free-standing table or a diamond table sintered or otherwise attached to a substrate.

#### SPINAL DISK IMPLANTS WITH BEARING SURFACES WEAR ENHANCED BY DIAMOND

20 The mode of devices included herein includes the enhancement of spinal disk implants 5100 with bearing surfaces wear-enhanced by the application or presence of Poly Crystalline Diamond Compact (PDC). All of the spinal disk implants Fig. 51 and Fig. 52 including the Cervical Disk (one through seven) 51, the Thoracic Disk  
25 (one through twelve) 52, and the Lumbar Disk (one through five) 53 can be enhanced by the application of PDC and are included as parts of this devices.

Figs. 53, 53-1, 53-2, 53-3 and 53-4 show a spinal disk replacement implant 101 which uses an Ultra High Molecular Weight Polyethylene (UHMWPE) hemispherical dome 5304 running against a cobalt chrome metal concave cup 5305.  
30 The UHMWPE dome insert 5304 is held in place by a tongue and groove retainer groove 5306.

Figs. 54-56 show the disk replacement implant 5101 in a typical installation between two adjacent vertebrae 5607, 5608, and Fig's. 55 and 56 depict the relative position of the implant 5101 viewed from the axial plane view, and the coronal plane view. Fig. 57 shows the relative side-to-side lateral angular motion possible by using  
35 a two part congruent bearing insert 5101. The angle  $\alpha$  typically allows a lateral bending range of plus or minus 10 degrees and is centered about the base of the spinous process. Fig. 58 shows the rotation  $\beta$  5810 available in the axial plane which



is not limited by the implant 5101 itself, but rather by the surrounding tissue such as muscle and ligaments. Fig. 59 shows the flexion angle  $\theta$  5911 which is typically 10 to 13 degrees, and the extension angle  $\phi$  5912 of Fig. 60 typically ranging from 5 to 8 degrees. A prosthetic spinal disk may permit some or all of the foregoing articulation, in greater or lesser degrees of flexibility.

Figs. 61 and 61-1 depict spinal disk implant 600102 including the use of a metal substrate 60013 on which PDC 60014 has been applied. The Substrate / PDC assembly 600103 is held in place by a tongue and groove retainer groove 60015 in the inferior endplate 60016. The mating convex cup 60017 has PDC 60018 applied directly to the superior endplate 60019.

The spinal disk implant 600104 shown in Figs. 62-1 and 62 shows a solid PDC dome insert 60020 held in place in the inferior endplate 60021 by a tongue and groove retainer groove 60022. The mating convex cup 60023 has PDC 60024 applied directly to the superior endplate 60025.

The PDC dome insert 600105 shown in Figs. 63 and 63-1 is held in place by a surrounding injection molded insert base 60026. The molded polymer 60026 surrounds the protrusions 60027 formed in the PDC 60028 restricting movement and holding it in place. The injected molded / PDC insert assembly 600106 is held in place in the inferior endplate 60029 by a tongue and groove retainer groove 60030. The mating convex cup 60031 has PDC 60032 applied directly to the superior endplate 60033.

Spinal disk implant 600107 depicted in Figs. 64 and 64-1 shows a solid PDC dome insert 60033 installed and held in place by an interference fit between the outside diameter 60034 of the dome insert and the receiving bore 60035 in the inferior endplate 60036. The mating convex solid PDC cup insert 60037 is also installed and held in place by an interference fit between the outside diameter of the cup insert 60038 and the receiving bore 60039 in the superior endplate 60040. Alternate retaining methods to hold the PDC inserts 60033 and 60037 in the inferior 60036 and superior 60040 endplates could involve the use of brazing, polymer bonding adhesives, retaining screws, or other standard attachment methods.

Figs. 65 through 65-4 show a three part spinal disk implant 600108 with three components including the inferior endplate 60041, superior endplate 60042, both of which contain a convex cup receiver 60043, 60044 for the domes 60045 and 60046, of the double hemispherical dome center part 60047. The two endplates 60041 and 60042 are generally fabricated from Cobalt Chrome metal but could be fabricated from any other biocompatible metal with sufficient wear qualities. The center double dome part 60047 is fabricated from High Molecular Weight Polyethylene (UHMWPE).

Fig. 66 shows a disk replacement implant 600108 in a typical installation between two adjacent vertebrae 60048, 60049, and Fig's. 67 and 68 depict the relative position of the implant 600108 viewed from the axial plane view, and the coronal plane view.

5        Fig. 69 shows the relative side-to-side lateral angular motion possible by using a three part congruent bearing insert 600108. The angles  $\alpha$  60050 typically allow a lateral bending range of plus or minus 10 degrees. Fig. 70 shows the rotation  $\beta$  60051 available in the axial plane which is not limited by the implant 600108 itself, but rather by the surrounding tissue. Fig's. 71 and 72 shows the flexion angles  $\theta$  10    60052 which are typically 10 to 13 degrees, and the extension angle  $\phi$  60053 Fig. 72 typically ranging from 5 to 8 degrees.

      Figs. 73 and 73-1 show a typical three piece spinal implant 600109 with PDC 60054 and 60055 applied to the inferior endplate 60056 and superior endplate 60057 to form the convex cup receivers 60059, 60060. The double hemispherical dome 15    center part 60061 has PDC 60062 applied to form the mating domes 60063, 600 64 for the cup receivers 60059, 60060.

      The three piece spinal implant 600110 shown in Figs 74 and 74-1 has been enhanced by applying PDC to the inferior 60065 and superior 60066 endplate convex cup receivers 60067, 60068. The PDC dome inserts 60069, 60070 have been 20    preformed and finished and then injection molded into the double dome hemispherical center part 60071. The PDC dome inserts 60069, 60070 are retained in place on the center part by the overlap 60072 of the injection molded polymer material.

      Solid PDC inferior 60073 and superior 60074 end plates are used in the three 25    piece spinal implant Figs. 75 and 75-1 600111 and for the double dome center part 60075. The center PDC double dome part 60075 has been injection molded into polymer material to form the complete articulating center part 60076. The overlap 60077 of the injection molded polymer material retains the outer ring bumper 60078 onto the solid or free standing PDC center part 60075.

30        The spinal implant 600112 of Figs. 76, 77 and 77-2 depicts the PDC enhancement of the bearing couple Dome 60079 and the convex cup / trough 60080. The PDC dome insert 60079 is installed into the superior endplate 60081 and held in place by an interference fit between the outside diameter 60082 of the dome insert 60079 and the receiving bore 60083 in the superior endplate 60081. The PDC cup / 35    trough insert 60080 is installed into the inferior endplate 60084 and held in place by an interference fit between the outside diameter 85 of the cup / trough insert 60080 and the receiving bore 60086 in the inferior endplate 60084. Alternate retaining methods to hold the PDC inserts 60079 and 60080 in the inferior 60084 and superior

60081 endplates could involve the use of brazing, polymer bonding adhesives, retaining screws, or other standard attachment methods. The configuration of the cup / trough insert 60080 allows for not only angular side-to-side motion and flexion and extension motion, but also provides for translational motion X 60086 Fig. 77 in the posterior and anterior directions plus or minus 1mm or more if desired. The radial sides of the dome 60079 will not be close enough to the sides of the cup / trough 60080 Fig. 77-1 to provide hydrodynamic support where even minimal bearing clearance has been provided, and likewise, the trough ends 60087 will not provide any support. Therefore, unlike the fully congruent bearings of the spinal inserts 600200 through 600111, the dome 60079 will be "point loaded" in the cup / trough 60080 generally promoting extreme bearing loading conditions. The extreme conditions wrought by non-congruent bearing configurations will generally not wear or function well with known biocompatible metals. This type of problem, depicted with the spinal implant 600112, functions extremely well when enhanced by PDC as described above. Test results showing less than 0.3mg weight loss for 30 million unlubricated cycles at five times the anatomical load are typical. Metal bearings tested under similar conditions would fail within a few hundred cycles.

Fig. 79 depicts the spinal implant 600113 section view wherein the congruent bearings concave cup 60088 and the matching dome 60089 have received surface enhancement of PCD.

The Spinal implant 114 of Fig. 80A and Fig. 80B depicts the PCD surface enhancement 60090 of the superior insert 60091, and the PCD surface enhancement 60092 of the inferior insert 60093.

Figs. 81A and 81B of the spinal implant 600115 shows the PCD surface enhancement 60094 of the superior insert 60095, and the PCD surface enhancement 60096, 60097, 60098 of the inferior insert 60099.

The spinal implant 600116 shown in Fig. 82A and Fig. 82B depict the PCD surface enhancement 600100, 600101, 600102 of the superior insert 600103, and the PCD surface enhancement 600104, 600105, 600106 of the inferior insert 600107.

The non-congruent spinal implant 600200 Fig. 83A and Fig. 83B depict the diamond enhancement 600108, 600109 of the dome surface 600110 and the concave running surface 600111. The sides 600112 of the running surface 600111 have also been PDC enhanced to prevent metallic wear by contact with the dome 600110.

Fig 84 depicts a similar bearing configuration 600201 wherein the convex running surface 600111 PDC 600109 enhancement does not include the sides 600116 of the convex running surface 600111. These implant bearing designs have

maximal angular  $\alpha$  600113 and  $\beta$  600114, and transitional motion X 600115, but relies totally on the ability of the bearing interface materials to handle the very significant point loading of the dome 600110 against the concave running surface 600111. This bearing, like the bearings 600112 of Fig. 76, benefits greatly from PDC enhancement.

Fig. 85 depicts a congruent spinal disk bearing 600202 with four mating surfaces which have been PDC enhanced. Two dome surfaces 600117, 600118 have PDC surfacing applied, and two concave cup mating receiving surfaces 600119, 600120 also have PDC surfacing applied.

The spinal implant 203 shown in Fig. 86 has been PDC enhanced on the inferior and superior convex surfaces 600121, 600122 as shown in Fig. 87 and Fig. 87-1 to improve the wear resistance and biocompatibility.

Fig. 88 and Fig. 89 depict a spinal disk implant device 600204 that has had the inferior convex surface 600123 and superior surface 600124 enhanced by the application of PDC.

Fig. 90 depicts a congruent spinal disk bearing 600205 with two mating surfaces which have been PDC enhanced. The inner ball surface 600125 has PDC surfacing applied, and the outer concave cup mating receiving surfaces 600126 also have PDC surfacing applied for increased wear resistance and biocompatibility.

The congruent bearing spinal implant shown in Fig. 91 as 600206 has been PDC enhanced on the inferior dome surface 600127, and the superior convex cup surface 600128 to improve the wear resistance and biocompatibility.

Fig. 92 depicts a congruent spinal disk bearing 600207 with two mating surfaces which have been PDC enhanced. The inner ball surface 600129 has PDC surfacing applied, and the outer concave cup mating receiving surfaces 600130 also have PDC surfacing applied for increased wear resistance and biocompatibility.

#### APPLICATION OF POLYCRYSTALLINE DIMOND COMPACTS FOR NON-CONGRUANT SPINAL IMPLANT BEARING SURFACES

Duplicating the anatomical motion of the human spine using spinal disk replacement implants is quite challenging. The motions that must be replicated in the implant device are originally the result of compound angular and translational motions allowed through the compliance of the pillow-like spine disk. The human vertebral disk has the ability to reshape itself instantaneously predicated on the vector forces applied to it while at the same time providing a flexible attachment between two adjacent vertebrae. For example, side-to-side bending motion in the coronal plane causes the spinal disk pad to become thin on the inside of the bend angle and larger on the outside of the bend angle. With the angular wedge type reshaping of the spinal disk in the side-to-side motion there is also some lateral

translation or parallel sliding of the two adjacent vertebrae. This same motion condition is also exhibited with flexion and extension of the body in the sagittal plane; however, the translational motion is significantly greater, often ranging from 1 to 2mm. Lateral rotation in the axial plane does not occur around the center of the spinal disk. The actual center of rotation is posterior to the spinal cord channel, often by several millimeters. This latter motion is almost completely translational parallel motion with the common centers of the adjacent vertebrae swinging in an arc.

Spinal disc implants utilizing congruent dome and cup bearings 600208 as in Fig 93 simply can not adequately duplicate the compound motions exhibited in the normal human anatomical motion. The very congruency of the bearing surfaces makes any kind of translational motion impossible. Lateral rotation Fig. 93-1 in the axial plane angle  $\beta$  600131, and flexion of Fig. 59 angle  $\theta$  5911, and Fig. 60 extension angle  $\phi$  5912 in the sagittal plane are severely restricted. This condition prevents the realization of full anatomical restoration following surgery and tends to place additional collateral forces on the adjacent spinal disc above and below the spinal disc implant leading to possible future problems.

The use of disc implants 600209 employing non-congruent dome and cup bearings of Fig 93 and 93-1 can provide substantially superior or near perfect anatomical duplication. By employing a dome, or similar dome shape, 600132 operating in a convex oval, kidney, or other suitably shaped mating receiver 600133 both angular and translational motion can be fully duplicated.

However, non-congruent bearings as utilized in spinal implants tend to produce overwhelming "point load forces" for typical biocompatible metals where the dome contacts the mating convex bearing receiver. These "point load forces" quickly wear away the bearing surfaces generally making them inoperable and producing wear particles which react with the surrounding tissue.

Polycrystalline diamond compact (PDC) utilized in spinal implants with non-congruent bearing surfaces completely ameliorates the "point load forces" problem associated with these types of bearings. One embodiment of the devices includes the use of PDC for the convex dome and convex articulating surface of a non-congruent spinal implant bearing. Fig. 94 and 94-1 depict a non-congruent spinal implant bearing 600209 wherein the dome 600132 has been fabricated using PDC, and also the convex articulating surface 600133 has been fabricated using PDC. To accomplish the necessary compound angular and translational motion required the shape of the dome 600132 would be generally hemispherical but could be elliptical, oval, flattened, or any other configuration that would allow for the motion required. The convex articulating surface 600133 could be shaped to allow the dome 600132

to not only rock angularly in the direction desired but to also translate horizontally in the axial plane X 600134.

Figures 94a and 94a-1 depict an alternative spinal prosthesis 600140a in which a hemispherical protrusion 600140a1 rides along a trough 600140a1 along an arc of a circle defined by circle center C located at the base of the spinal process, and radius R to provide  $\beta$  degrees of rotational movement within the trough. The trough has a kidney bean appearance.

The actual contour of the convex surface of the recess can be designed to meet any special angular and translational requirement. Figs. 95, 95-1 and 95-2 show a spinal insert 600210 configuration wherein the radius r2 600135 of the convex articulating surface 600138 are significantly larger than the dome radius r1 600136 allowing the dome 600137 to rotate freely, but to also translate in any direction until restrained from further movement by the surrounding tissue.

Figs. 96, 96-1 and 96-2 depict a modified articulating surfaces 600211 wherein the convex articulating surface radius r4 600138 is significantly larger than the end radiuses r3 600139, and the radius r6 600140 is significantly larger than the end radiuses r5 600141. The center radiuses r4 600138 and r6 600140 can be equal, but may also be unequal, also the end radiuses r3 600139 and r5 600141 can be equal, but may also be unequal. The dome radius r2 600142 would generally be slightly smaller than the smallest of radiuses r3 600139 and r5 600141.

Figs. 97, 97-1 and 97-2 depict a modified articulating surfaces 600212 wherein the recessed articulating surface has a flat area 600143 and end radiuses r3 600144. The end radiuses r3 600144 and r4 600145 can be equal, but may also be unequal. The dome radius r2 600146 would generally be slightly smaller than the smallest of radiuses r3 600144 and r4 600145.

Figs. 98, 98-1 and 98-2 depict a modified articulating surfaces 600213 wherein the convex articulating surface has a conical area 600147 defined by the angle  $\Phi$  600148 and end radiuses r3 600149. The end radiuses r3 600149 and r4 600150 can be equal, but may also be unequal. The dome radius r2 600151 would generally be slightly smaller than the smallest of radiuses r3 600149 and r4 600150.

Fig. 99-1 and 99-2 depict a modified articulating surface 600214 wherein the convex articulating surface is an elliptically shaped area 600152. The elliptical shape 600152 can be equal to the elliptical shape 600153, but may also be unequal or another shape configuration. The dome radius r2 600154 would generally be of size to allow for the required angular and transitional motion.

Figs. 100, 100-1 and 100-2 depict a modified articulating surface 600215 wherein the convex articulating surface 600155 is defined by a three dimensional mathematically defined function of the general form:

$$\text{Surface} = f(r_{ijk}, \theta_{ijk}, \Phi_{ijk})$$

The dome radius r2 600156 would generally be of size to allow for the required angular and transitional motion.

Figs. 101 and 101-1 show modified articulating surfaces for a three part spinal implant insert 600216 configuration wherein the radius r1 600157 of the convex articulating surface 600158 is significantly larger than the dome radiuses r2 600159 allowing the domes to rotate freely, but to also translate in any direction until restrained from further movement by the surrounding tissue.

Figs. 102, 102-1 and 102-2 depict modified articulating surfaces for a three part spinal implant 600217 wherein the convex articulating surface radiuses r4 600159 is significantly larger than the end radiuses r3 600160 and the radius r6 600161 is significantly larger than the end radiuses r5 600162. The center radiuses r4 600159 and r6 600161 can be equal, but may also be unequal; also the end radiuses r3 600160 and r5 600162 can be equal, but may also be unequal. The dome radius r2 600163 would generally be slightly smaller than the smallest of radiuses r3 600160 and r5 600162.

Figs. 103, 103-1 and 103-2 depict articulating surfaces for a three part spinal implant 600218 wherein the recessed articulating surface has a flat area 600164 and end radiuses r3 600165. The end radiuses r3 600165 and r4 600166 can be equal, but may also be unequal. The dome radius r2 600167 would generally be slightly smaller than the smallest of radiuses r3 600165 and r4 600166.

Figs. 104, 104-1 and 104-2 depict an articulating surfaces for a three part spinal implant 600219 wherein the convex articulating surface has a conical area 600168 defined by the angle  $\Phi_{600169}$  and end radiuses r3 600170. The end radiuses r3 600170 and r4 600171 can be equal, but may also be unequal. The dome radius r2 600172 would generally be slightly smaller than the smallest of radiuses r3 600170 and r4 600171.

Figs. 105, 105-1 and 105-2 depict an articulating surface for a three part spinal implant 600220 wherein the convex articulating surface is an elliptically shaped area 600173. The elliptical shape 600173 can be equal to the elliptical shape 600174, but may also be unequal or another shape configuration. The dome radius r2 600175 would generally be of size to allow for the required angular and transitional motion.

Figs. 106, 106-1 and 106-2 depict articulating surfaces for a three part spinal implant 600221 wherein the convex articulating surface 600176 is defined by a three dimensional mathematically defined function of the general form:

$$\text{Surface} = f(r_{ijk}, \theta_{ijk}, \Phi_{ijk})$$

5 The dome radius  $r_2$  600177 would generally be of size to allow for the required angular and transitional motion.

Figs. 107 and 107-2 depict a three part spinal implant 600222 wherein the inferior endplate 600178 and the superior endplate 600179 have been fabricated using PDC. The outer surfaces 600180, 600181 and the attachment protrusions 600182 which will contact the adjacent vertebrae following surgery have been  
10 chemically leached using a suitable acid leaching bath such as nitric-hydro sulfuric acid to remove the interstitial metal between the diamond crystals. The depth of the leached areas 600180, 600181, 600182 would generally range from 0.5 to 1.5mm or more. The voids left between the diamond crystals would be available for bone in growth infusion, or the application of other bone growth surfaces, or bone growth  
15 accelerators such as Hydroxyl Appetite.

Figs. 108 and 108-1 depict a two part spinal implant 600223 wherein the inferior endplate 600183 and the superior endplate 600184 have been fabricated using PDC. The outer surfaces 600185, 600186 and the attachment protrusions 600187 which will contact the adjacent vertebrae following surgery have been  
20 chemically leached using a suitable acid leaching bath such as nitric-hydro sulfuric acid to remove the interstitial metal between the diamond crystals. The depth of the leached areas 600185, 600186, 600187 would generally range from 0.5 to 1.5mm or more. The voids left between the diamond crystals would be available for bone in growth infusion, or the application of other bone growth surfaces or bone growth  
25 accelerators. In addition, any bone mating surface depicted anywhere herein could include a bone growth accelerator, a roughened or textured surface to promote bone fixation, pores to permit bone ingrowth, and protrusions to achieve mechanical bone fixation. In addition, adhesives, glues or epoxies may also be used to achieve bone fixation.

#### 30 SPINAL IMPLANT FIXATION METHOD USING SCREWS WITH PARTIAL HEMASPHERICAL ENGAGEMENT

The devices shown in Fig. 109, 109-1, 109-2, 109-3a, 109-3b, 109-4 and 109-5 disclose a method and apparatus by which one or more screws 7001 may be used to assist in the installation of a spinal implant appliance 7002, provide partial  
35 fixation during the period of bone in-growth to the receptor surfaces 7003 of the appliance 7002, and full fixation for the life of the implant. Another object of this devices is to provide fixation without any protrusion of the fixation screws 7001 or



other components into the anterior or posterior areas surrounding the spinal implant device 7002.

Fixation of the spinal implant device 7002 is accomplished by the engagement of slightly less than one-half of the hemispherical portion of the full length of the screw threads 7004 of the fixation screws 7001 into the adjacent vertebral bones 7005 as depicted in the Figures. The complementary pressure of the tissue tending to hold and draw the two corresponding vertebra 7004 together generally provides contact pressures 7006 normal toward the screw thread 7004 surfaces and the bone surface 7007 allowing adequate frictional and buttressing fixation. The screws 7001 are held captive in the appliance 7002 superior 7008 and inferior 7009 plate surfaces 7003 by machining the screw holes 70010 slightly below the plate surfaces 7003 of the appliance 7002 which interfaces with the bone surfaces 7007. The centerline locating dimension  $\beta$  70011 of the screw holes 70010 can be adjusted based on the diameter 70012 of the screw 7001 to ensure that part of the plate material 70013 extends slightly beyond the centerline of the screw 7001 securing it in place within the plates 7008 and 7009. The screw holes 70010 in the superior 7008 and the inferior 7009 plates of the implant device 7002 can be a drilled hole only 70014 as shown in Fig. 109-3a with a diameter slightly larger than the major diameter 70012 of the screws 7001, or tap drilled to the minor of the screw 7001 and then threaded 70015 as shown in Fig 109-3b.

One, two, or more fixation screws 7001 could be used to provide the device 7002 securement. The fixation screws 7001 can also be located at an angle  $\alpha$  70016 ranging between 0.0 Deg and 90 Deg. One embodiment would locate two screws at an angle  $\alpha$  70016 of approximately 35 Deg. which provides the most favorable strain resistance against component forces exerted laterally along the horizontal plane of the body. Threads in the vertebrae 7005 bone surface 7007 can be created by using the screw 7001 only, or by pre-cutting the threads 70015 using a typical thread tap of the correct size, form, and length in conjunction with a suitable tap drill hole location fixture and tapping fixture.

The head 70017 of the securing screws 7001 is recessed into a relief counter-bore 70018 of Fig. 109-5 to prevent any protrusion at the anterior face of the spinal implant 7002.

The surfaces 7003 of the superior 7008 and inferior 7009 plates of the spinal implant device 2 may be prepared for bone in growth by the application of Hydroxy Apatite coating, chemical coating, attached metal beads, etched surfacing, leached poly crystalline diamond, or any other treatment that would promote bone ingrowth and attachment.

## SPINAL IMPLANT FIXATION METHOD USING SCREWS WITH ANGULAR VECTOR BONE ENGAGEMENT

The devices shown in Figs. 110, 110-1, 110-2 and 110-3 disclose methods and apparatuses by which one or more screws 8001 may be used to assist in the  
5 installation of a spinal implant appliance 8002, provide partial fixation during the period of bone in-growth to the receptor surfaces 8003 of the appliance 8002, and full fixation for the life of the implant. Another object of this devices is to provide fixation without any protrusion of the fixation screws 8001 or other components into the anterior or posterior areas surrounding the spinal implant device 8002.

10 Fixation of the spinal implant device 8002 is accomplished by the engagement of the screw threads 8004 of the fixation screws 8001 into the adjacent vertebral bones 8005 as more fully depicted in the Figures. The complementary pressure of the tissue tending to hold and draw the two corresponding vertebra 8005 together generally provides contact pressure 8006 toward the bone surfaces 8007  
15 and is augmented by component forces associated with the holding resistance of the screws 8001 acting at angles  $\sigma$  8008 and angle  $\alpha$  8009.

One, two, or more fixation screws 8001 could be used to provide the device 8002 securement. The fixation screws 8001 can be located at an angel  $\alpha$  8009 ranging between 0.0 Deg and 90 Deg. and angle  $\sigma$  8008 ranging between  
20 approximately 10 Deg. and 45 Deg. One embodiment would locate two screws at an angle  $\sigma$  8008 of approximately 25 Deg. and angle  $\alpha$  8009 at approximately 35 Deg. which would provide the most favorable strain resistance against component forces exerted axially along the median/coronal planes and laterally along the horizontal plane of the body. Threads in the vertebrae 8005 bone can be created by  
25 using the screw 8001 only, or by pre-cutting the threads 80010 Fig. 110-3 using a typical thread tap of the correct size, form, and length in conjunction with a suitable tap drill hole location fixture and tapping fixture.

The head 80011 of the securing screws 8001 is recessed into a relief counter-bore 80012 of Fig. 110-3 to prevent any protrusion at the anterior face of the spinal  
30 implant 8002.

The surfaces 8003 of the superior 80013 and inferior 80014 plates of the spinal implant device 8002 may be prepared for bone in growth and attachment.

## SPINAL IMPLANT FIXATION METHOD USING SCREWS WITH ANGULAR VECTOR PLATE ENGAGEMENT

35 The devices shown in Figures 111, 111-1, 111-2 and 111-3 discloses methods and apparatuses by which one or more screws 8501 may be used to assist in the installation of a spinal implant appliance 8502, provide partial fixation during the period of bone in-growth to the receptor surfaces 8503 of the appliance 8502,

and full fixation for the life of the implant. Another object of this devices is to provide fixation without any protrusion of the fixation screws 8501 or other components into the anterior or posterior areas surrounding the spinal implant device 8502.

Fixation of the spinal implant device 8502 is accomplished by the  
5 engagement of the screw threads 8504 of the fixation screws 8501 into the superior 8505 and inferior 8506 implant plates 8507 after having passed through the adjacent vertebral bones 8508 as more fully depicted in the Figures. The complementary pressure of the tissue tending to hold and draw the two corresponding vertebra 8508 together generally provides contact pressure 8509 toward the bone surfaces 85010  
10 and is augmented by component forces associated with the holding resistance of the screws 8501 acting at angles  $\sigma$  85011 and angle  $\alpha$  85012.

One, two, or more fixation screws 8501 could be used to provide the device 8502 securement. The fixation screws 8501 can be located at an angle  $\alpha$  85012 ranging between 0.0 Deg and 90 Deg. and angle  $\sigma$  85011 ranging between  
15 approximately 10 Deg. and 45 Deg. One embodiment would locate two screws 8501 at an angle  $\sigma$  85011 of approximately 25 Deg. and angle  $\alpha$  85012 at approximately 35 Deg. which would provide the most favorable strain resistance against component forces exerted axially along the median/coronal planes and laterally along the horizontal plane of the body. The fixation screws engage the  
20 superior 8505 and inferior 8506 plates 8507 at in pre-threaded holes 85013. The fixation screws 8501 can be threaded along the full length of the screw 8501, or only for the length which engages the superior 8505 and inferior 8506 plates 8507. Clearance holes for the fixation screws 8501 are pre-drilled using a suitable location fixture to ensure proper location and engagement of the screws 8501 into the  
25 superior 8505 and inferior 8506 plates 8507.

The head 85014 of the securing screws 8501 is recessed into a relief counter-bore 85015 to prevent any protrusion at the anterior face of the spinal implant 8502.

The surfaces 8503 of the superior 8505 and inferior 8506 plates 8507 of the spinal implant device 8502 may be prepared for bone in growth.

#### 30 SPINAL IMPLANT FIXATION METHOD USING SECURMENT LUGS WITH ATTACHMENT SCREWS AND ANTI ROTATION POSITIONIONERS

The devices shown in Figs. 112, 112-1, 112-2 and 112-3 disclose method and apparatuses by which one or more lugs or clips 9001 may be used to assist in the installation of a spinal implant appliance 9002, provide partial fixation during the  
35 period of bone in-growth to the receptor surfaces 9003 of the appliance 9002, and full fixation for the life of the implant. Another object of this device is to provide fixation without any protrusion of the fixation clips 9001, screws 9004 or other components into the anterior or posterior areas surrounding the spinal implant device 9002.

Fixation of the spinal implant device 9002 is accomplished by the engagement of the lugs 9001 into the recesses 9005 previously machined into the vertebra by the surgeon. The clips 9001 may be stabilized by the use of a square or rectangular matching tongue protrusions 9006 and grooves 9007 running parallel and perpendicular to the median plane of the body. Other tongue and groove configurations such as the angular tongue 9008 and angular groove, or a hemispherical tongue and grooves could be used to prevent rotation of the clip.

The head 90012 of the securing screw 9004 is recessed into a relief counter-bore 90013 to prevent any protrusion at the anterior face of the spinal implant 9002. The clip 9001 is also rounded 90014 and recessed 90015 to prevent any protrusion at the anterior face of the spinal implant 9002. The surfaces 9003 of the superior 90016 and inferior 90017 plates of the spinal implant device 9002 may be prepared for bone in growth.

While the present devices and methods have been described and illustrated in conjunction with a number of specific configurations, those skilled in the art will appreciate that variations and modifications may be made without departing from the principles herein illustrated, described, and claimed. The present invention, as defined by the appended claims, may be embodied in other specific forms without departing from its spirit or essential characteristics. The configurations described herein are to be considered in all respects as only illustrative, and not restrictive. All changes which come within the meaning and range of equivalency of the claims are to be embraced within their scope.

1. An articulating diamond-surfaced prosthetic spinal implant for implantation between vertebrae in a human body, the implant comprising:
- 5 a first component,  
said first component having a convex protruding dome member,  
said dome member including a first component load bearing and articulation surface,  
said first component load bearing and articulation surface being formed at  
10 least in part by a sintered polycrystalline diamond table,  
said sintered polycrystalline diamond table in said first component serving to provide a durable, biocompatible and low-friction surface for articulation of the implant,  
a second component,  
15 said second component having a concave trough,  
said trough having a shape and size that permits said protruding dome member to protrude therein,  
said trough having a shape and size that permits contact of said protruding dome member therewith at a plurality of contact points,  
20 said trough including a second component load bearing and articulation surface,  
said second component load bearing and articulation surface being formed at least in part by a sintered polycrystalline diamond table,  
said sintered polycrystalline diamond table in said second component serving  
25 to provide a durable, biocompatible and low-friction surface for articulation of the implant,  
said first component being movable with respect to said second component in at a point that has diamond to diamond contact between said first and second components.
- 30 2. An implant as recited in claim 1 wherein said first component and said second component are able to articulate with respect to each other to provide rotation about the axial, coronal and/or sagittal axes of the human spine.
3. An implant as recited in claim 1 wherein said first component and said second component are able to articulate with respect to each other to provide  
35 translation in the axial plane of a human spine.
4. An implant as recited in claim 1 wherein said first component and said second component are able to articulate with respect to each other to provide rotation about the axial, coronal and/or sagittal axes of the human spine; and wherein

said first component and said second component are able to articulate with respect to each other to provide translation in the axial plane of a human spine;

and wherein said rotation and translation accommodate anterior bending, posterior bending, lateral bending, twisting of a spine about its longitudinal axis,  
5 anterior translation, posterior translation and lateral translation.

5. An implant as recited in claim 1 wherein said dome member has a shape that is at least partially spherical convex.

6. An implant as recited in claim 1 wherein said first and second components include congruent bearing surfaces.

10 7. An implant as recited in claim 1 wherein said first and second components include non-congruent bearing surfaces.

8. An implant as recited in claim 1 further comprising:  
carbon to carbon bonds in at least one of said sintered polycrystalline diamond table.

15 9. An implant as recited in claim 8 further comprising:  
sp<sup>3</sup> carbon bonds in at least one of said sintered polycrystalline diamond table.

10. An implant as recited in claim 9 further comprising:  
a crystalline diamond structure in at least one of said sintered polycrystalline  
20 diamond table.

11. An implant as recited in claim 10 further comprising:  
interstitial spaces in said crystalline diamond structure.

12. An implant as recited in claim 11 further comprising:  
solvent-catalyst metal in said interstitial spaces.

25 13. An implant as recited in claim 12 further comprising:  
diamond to metal bonds between said solvent-catalyst metal and diamond in said sintered polycrystalline diamond table.

14. An implant as recited in claim 13 wherein said solvent-catalyst metal was used to facilitate sintering of said polycrystalline diamond compact at high  
30 temperature and high pressure.

15. An implant as recited in claim 12 wherein said solvent-catalyst metal includes a material selected from the group consisting of Co, Cr and Mo.

16. An implant recited in claim 12 wherein said solvent-catalyst metal includes CoCr.

35 17. An implant as recited in claim 12 wherein said solvent-catalyst metal includes CoCrMo.

18. An implant as recited in claim 1 further comprising a gradient transition zone in at least one of said sintered polycrystalline diamond tables, said gradient

transition zone having a first side and a second, said gradient transition zone having both solvent-catalyst metal and diamond therein, and said gradient transition zone exhibiting a transition of ratios of percentage content of solvent-catalyst metal to diamond from said first side to said second side such that at a first point in said  
5 gradient transition zone, the ratio of percentage content of solvent-catalyst metal to diamond is greater than it is at a second point in gradient transition zone.

19. An implant as recited in claim 1 wherein at least one of said sintered polycrystalline diamond tables is a free standing diamond table.

20. An implant as recited in claim 1 wherein at least one of said sintered  
10 polycrystalline diamond tables includes diamond sintered to a substrate.

21. An implant as recited in claim 1 wherein at least one of said sintered polycrystalline diamond tables includes a diamond table attached to a substrate.

22. An articulating diamond-surfaced prosthetic spinal implant for implantation between vertebrae in a human body, the implant comprising:  
15 a protrusion,  
a protrusion load bearing and articulation surface located on said protrusion,  
said protrusion load bearing and articulation surface being formed at least in part by diamond,  
a receptacle,  
20 a receptacle load bearing and articulation surface located on said receptacle,  
said receptacle load bearing and articulation surface being formed at least in part by diamond,  
said protrusion and said receptacle being sized and shaped to accommodate said protrusion protruding into said receptacle, and contact of said protrusion load  
25 bearing and articulation surface with said receptacle load bearing and articulation surface,  
said contact of said protrusion with said receptacle being accomplished by diamond to diamond contact of said protrusion and receptacle load bearing and articulation surfaces.

30 23. An articulating diamond-surfaced prosthetic spinal implant for implantation between vertebrae in a human body, the implant comprising:  
a protrusion,  
a protrusion load bearing and articulation surface located on said protrusion,  
said protrusion load bearing and articulation surface being formed at least in  
35 part by diamond,  
a receptacle,  
a receptacle load bearing and articulation surface located on said receptacle,  
said receptacle load bearing and articulation surface being formed at least in

part by diamond,

said protrusion and said receptacle being sized and shaped to accommodate said protrusion protruding into said receptacle, and said protrusion load bearing and articulation surface contacting said receptacle load bearing and articulation surface,

5        said contact of said protrusion with said receptacle being accomplished by diamond to diamond contact of said protrusion and receptacle load bearing and articulation surfaces,

      said contact of said protrusion with said receptacle occurring at a diamond to diamond contact point where diamond of said protrusion contacts diamond of said  
10        receptacle,

      said protrusion being pivotally movable with respect to said receptacle about said diamond to diamond contact point to provide translational or rotational movement of said protrusion with respect to said receptacle.

24.     An articulating diamond-surfaced prosthetic spinal implant for  
15        implantation between vertebrae in a human body, the implant comprising:

      a protrusion,

      a protrusion load bearing and articulation surface located on said protrusion, said protrusion load bearing and articulation surface being formed at least in  
part by diamond,

20        said protrusion having a curvature defined by at least one radius R1,  
      a receptacle,

      a receptacle load bearing and articulation surface located on said receptacle, said receptacle load bearing and articulation surface being formed at least in  
part by diamond,

25        said receptacle having a curvature defined by at least one radius R2,

      said protrusion and said receptacle being sized and curved to accommodate said protrusion protruding into said receptacle, and to accommodate said protrusion load bearing and articulation surface contacting said receptacle load bearing and articulation surface,

30        said contact of said protrusion with said receptacle being accomplished by diamond to diamond contact of said protrusion and receptacle load bearing and articulation surfaces,

      said contact of said protrusion with said receptacle occurring at a diamond to diamond contact point where diamond of said protrusion contacts diamond of said  
35        receptacle,

      said protrusion being translationally movable with respect to said receptacle in the axial plan of a human spine, said translational movement being accomplished by a sliding or rolling movement of diamond against diamond;



wherein R1 and R2 are chosen to accommodate said translational movement;  
and

wherein at least some of said translational movement occurs in the axial  
plane of a human spine about an arc of a circle having a radius R3 whose center is  
5 located at the base of the spinal process of a human spine, and wherein R3 is not  
equal to R1 or R2.

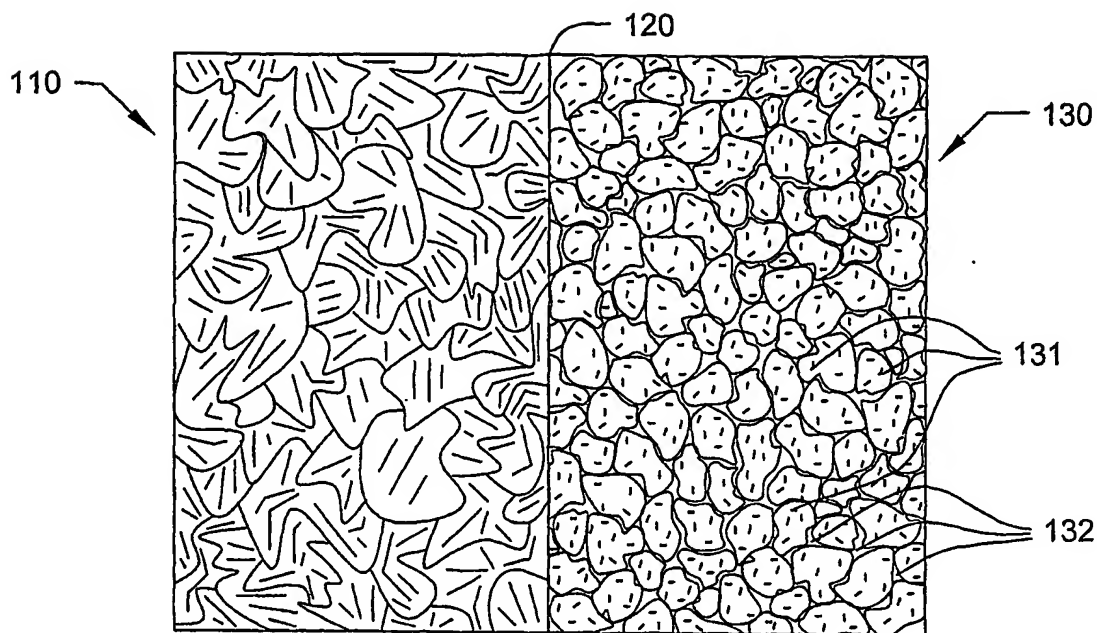


Fig. 1A

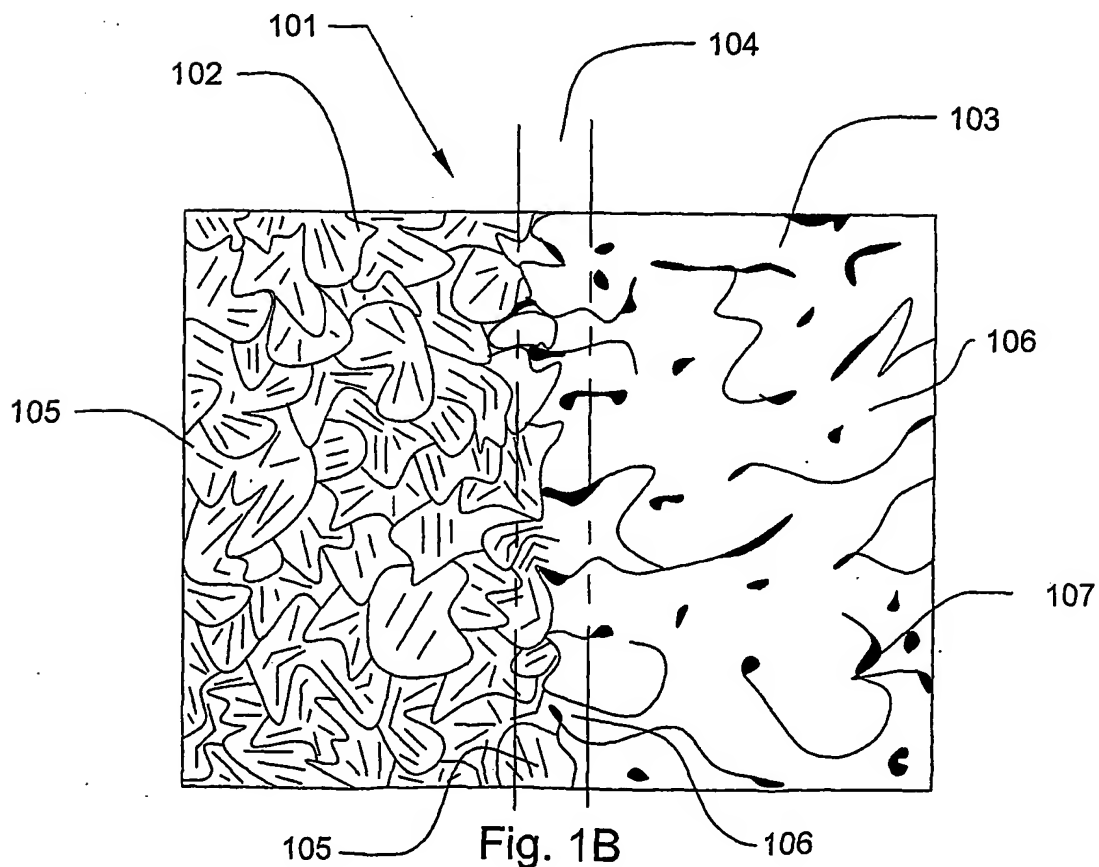
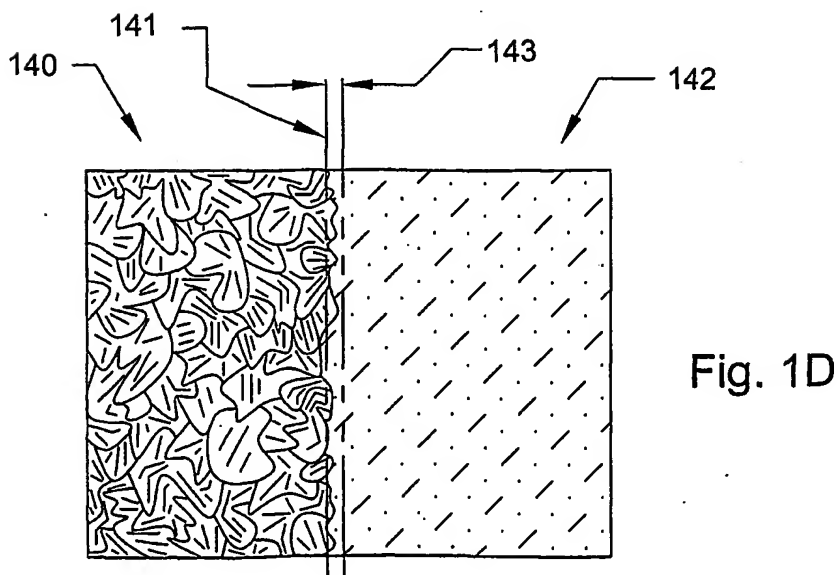
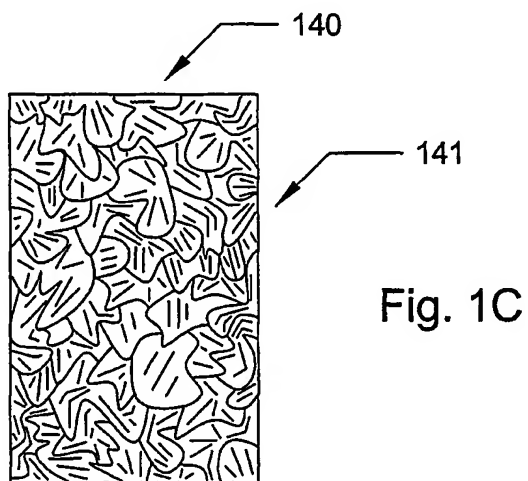
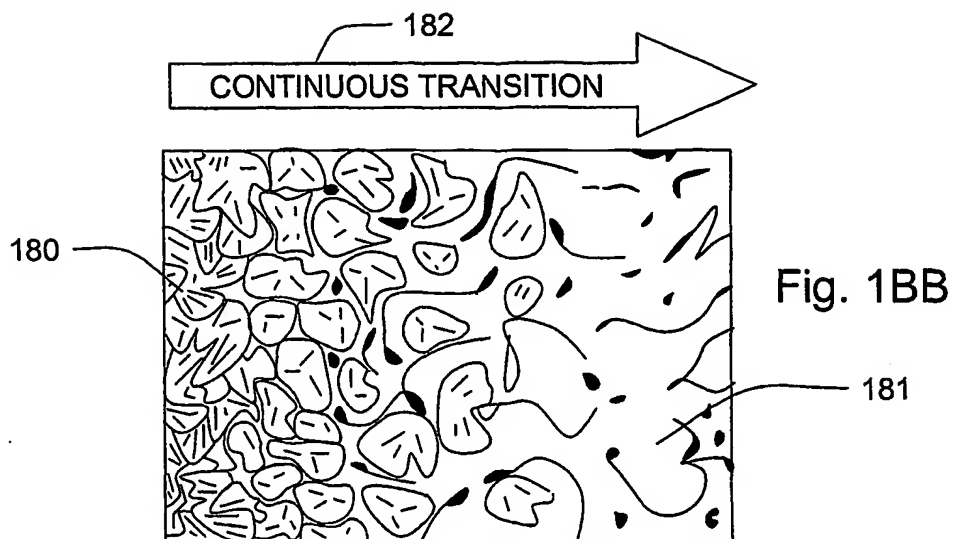


Fig. 1B



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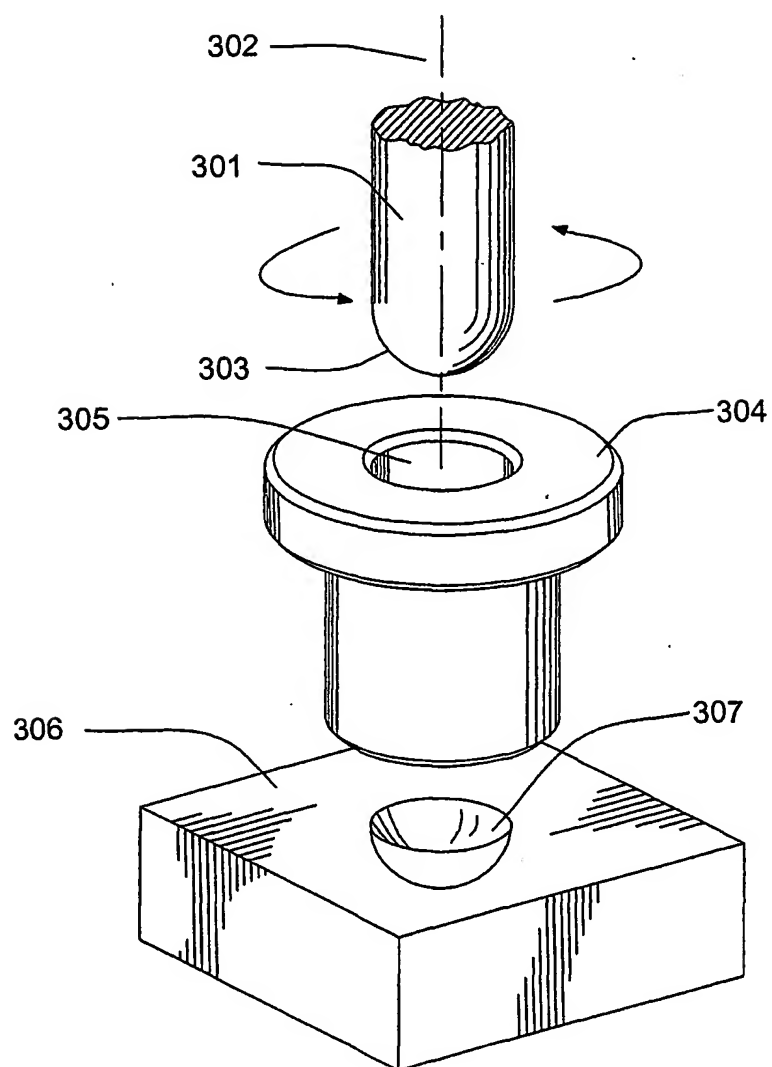


Fig. 3

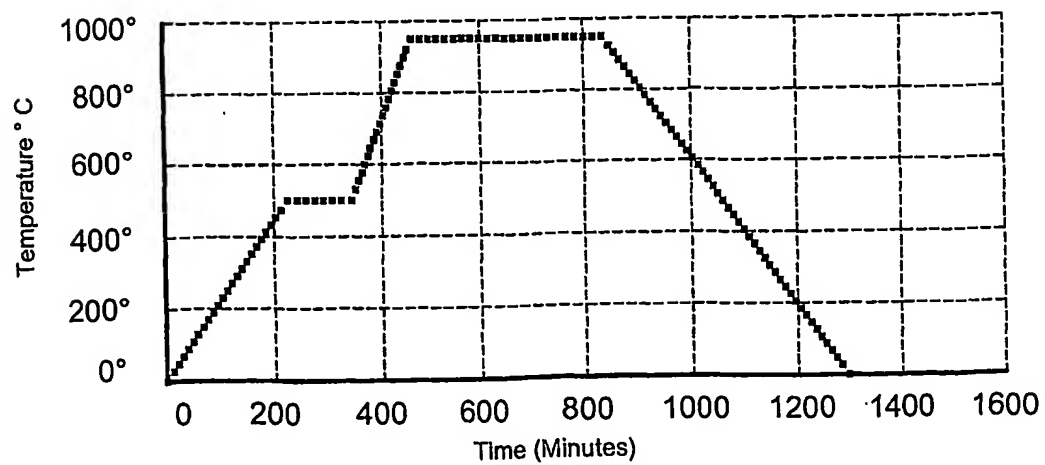


Fig. 4

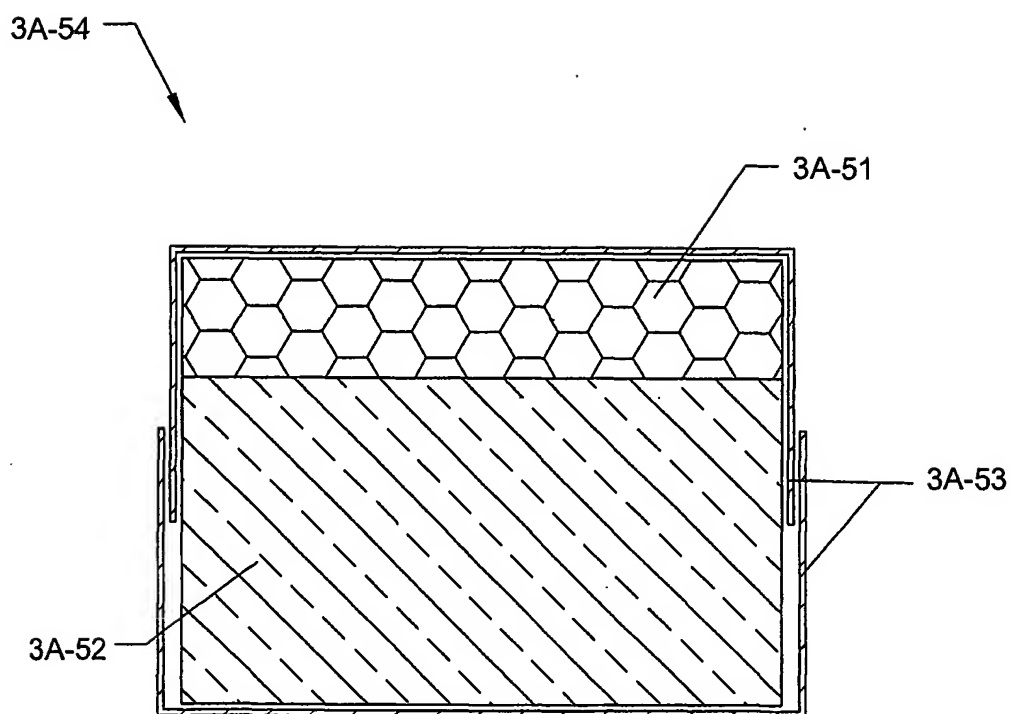


Fig. 3A-1

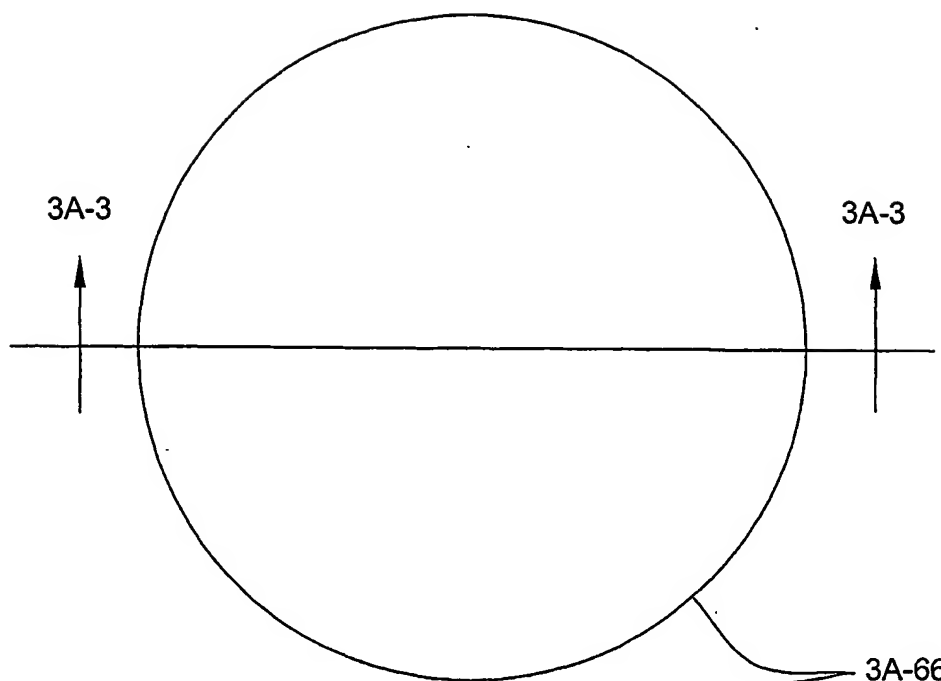


Fig. 3A-2

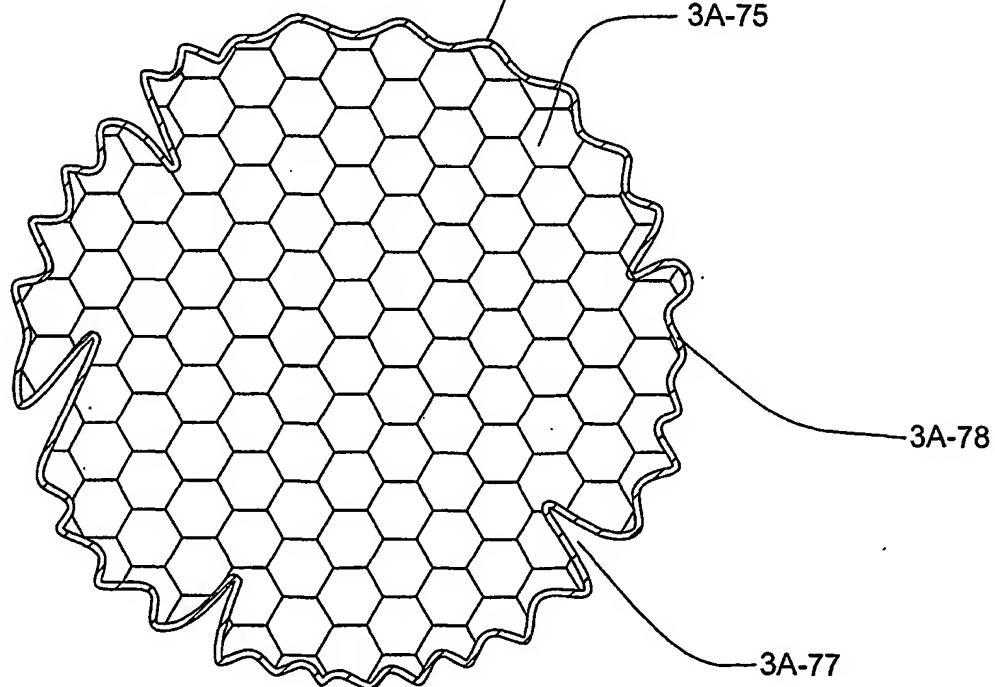


Fig. 3A-3

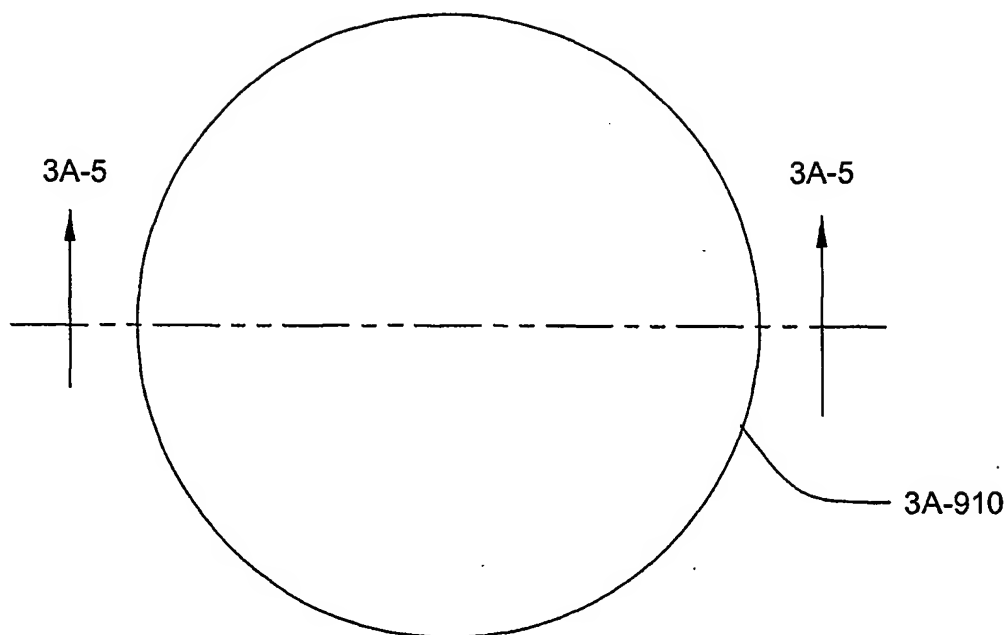


Fig 3A-4

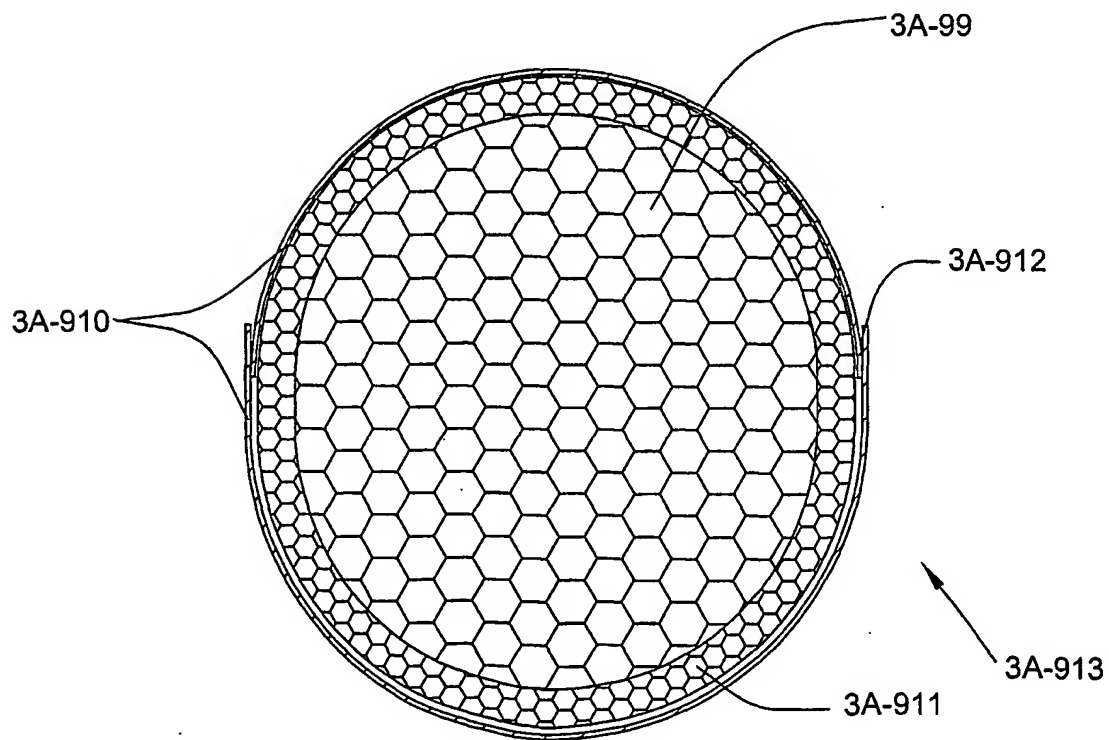


Fig 3A-5

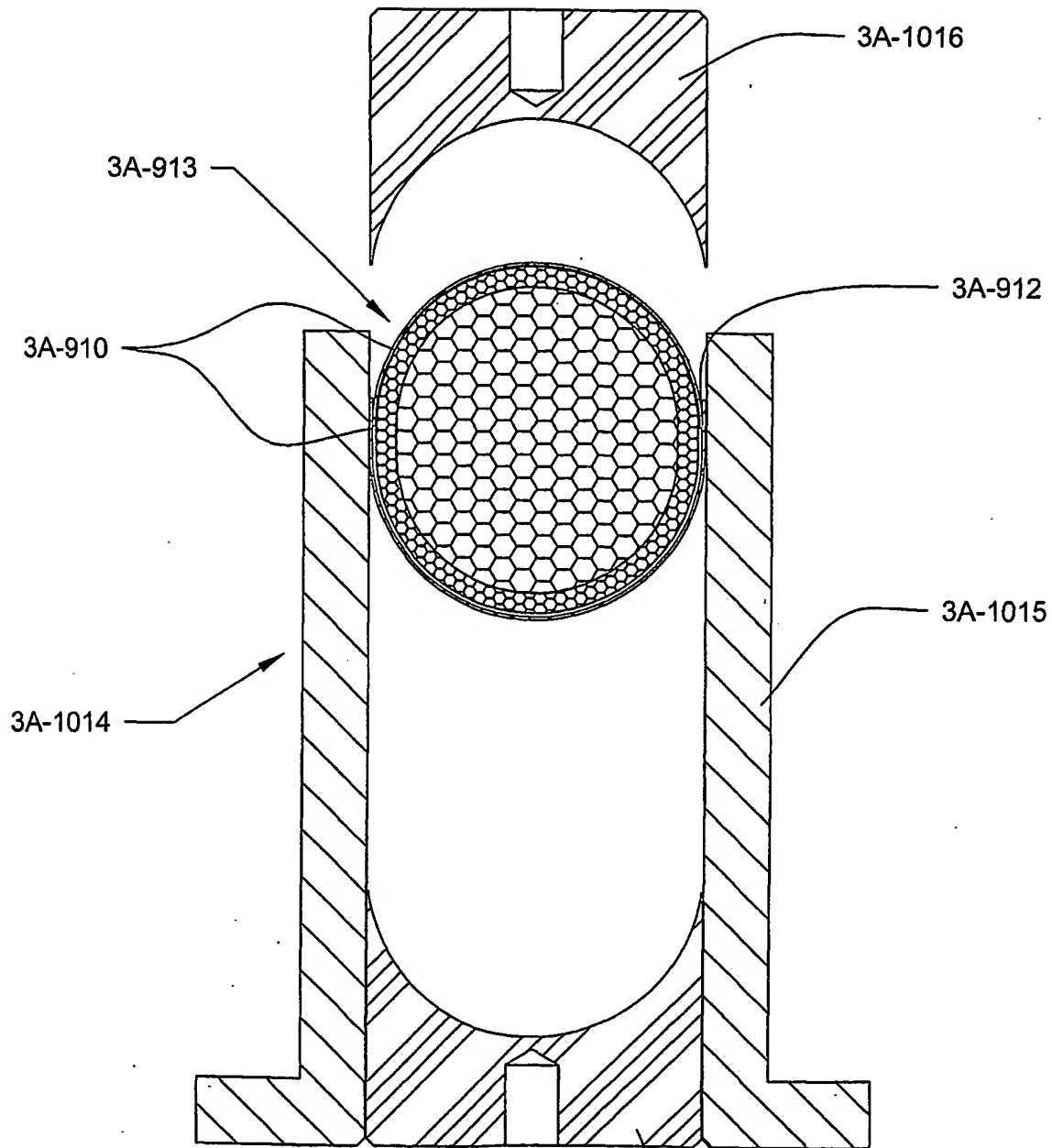


Fig. 3A-6

3A-1017



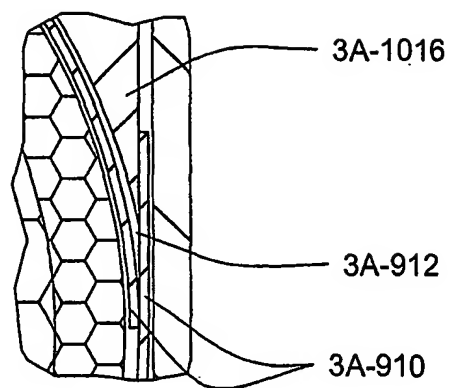


Fig. 3A-7-1

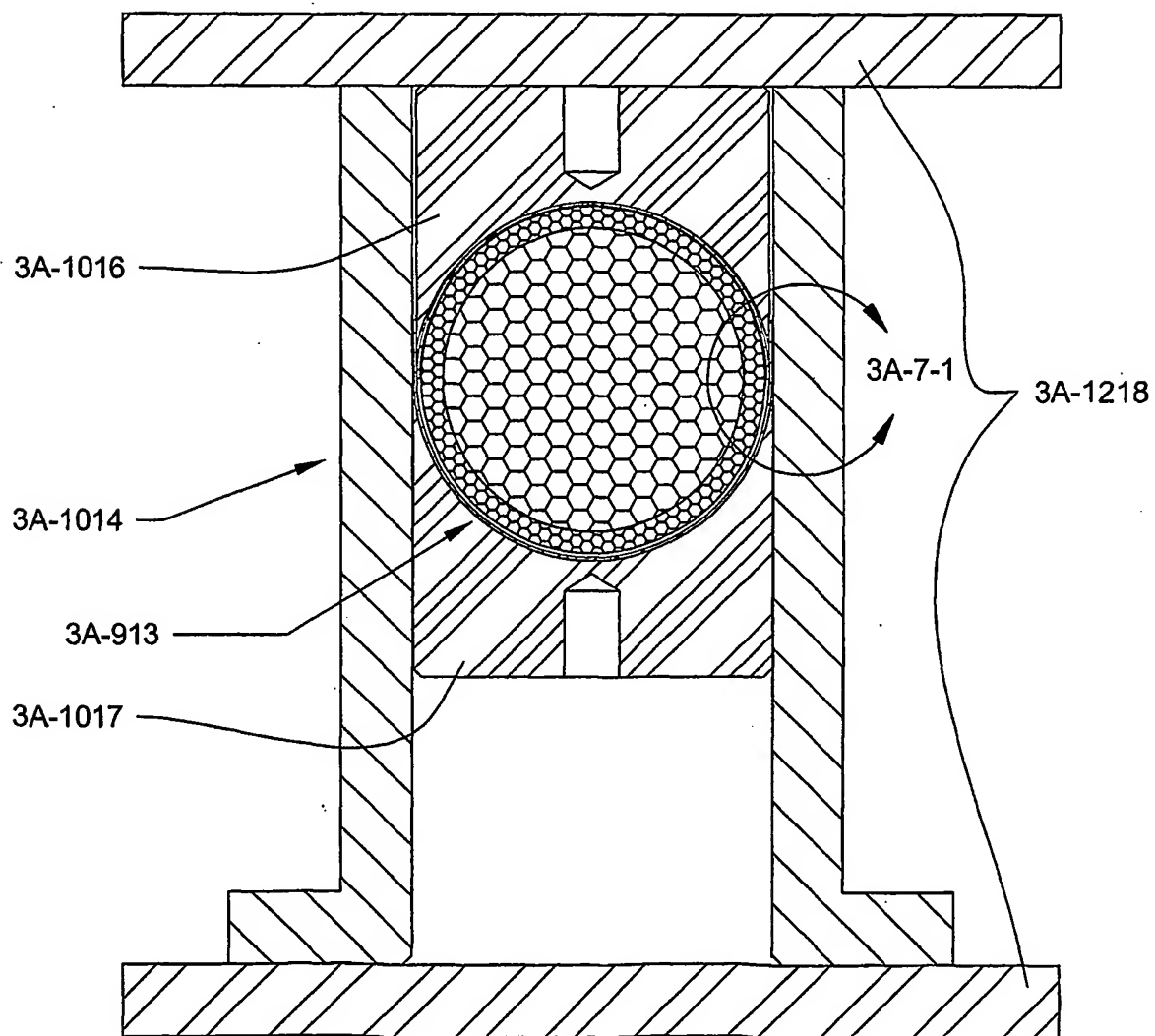


Fig. 3A-7

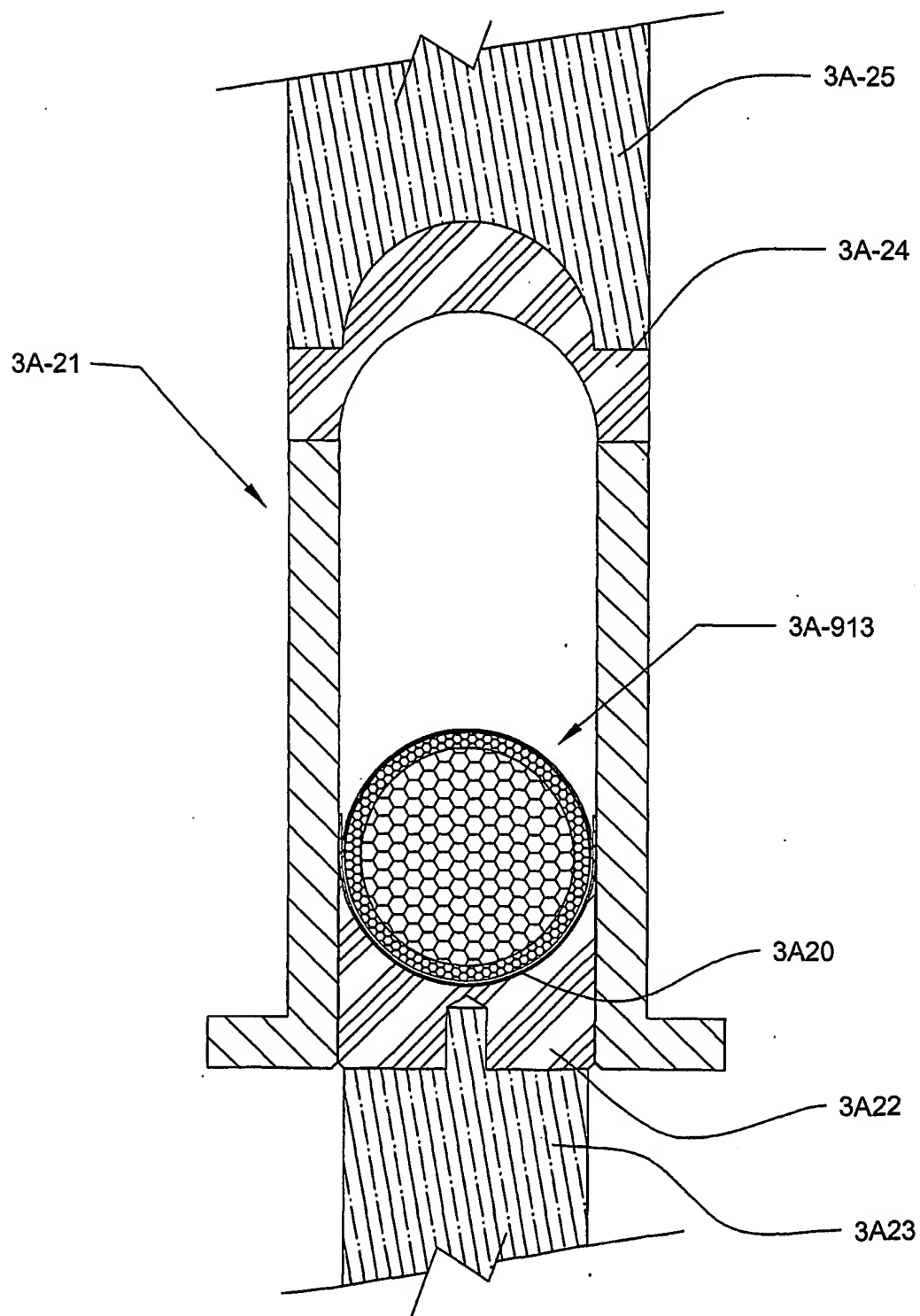


Fig. 3A-8

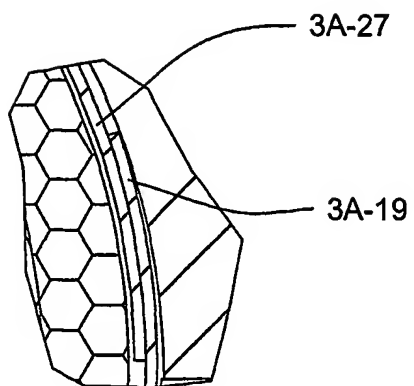


Fig. 3A-9-1

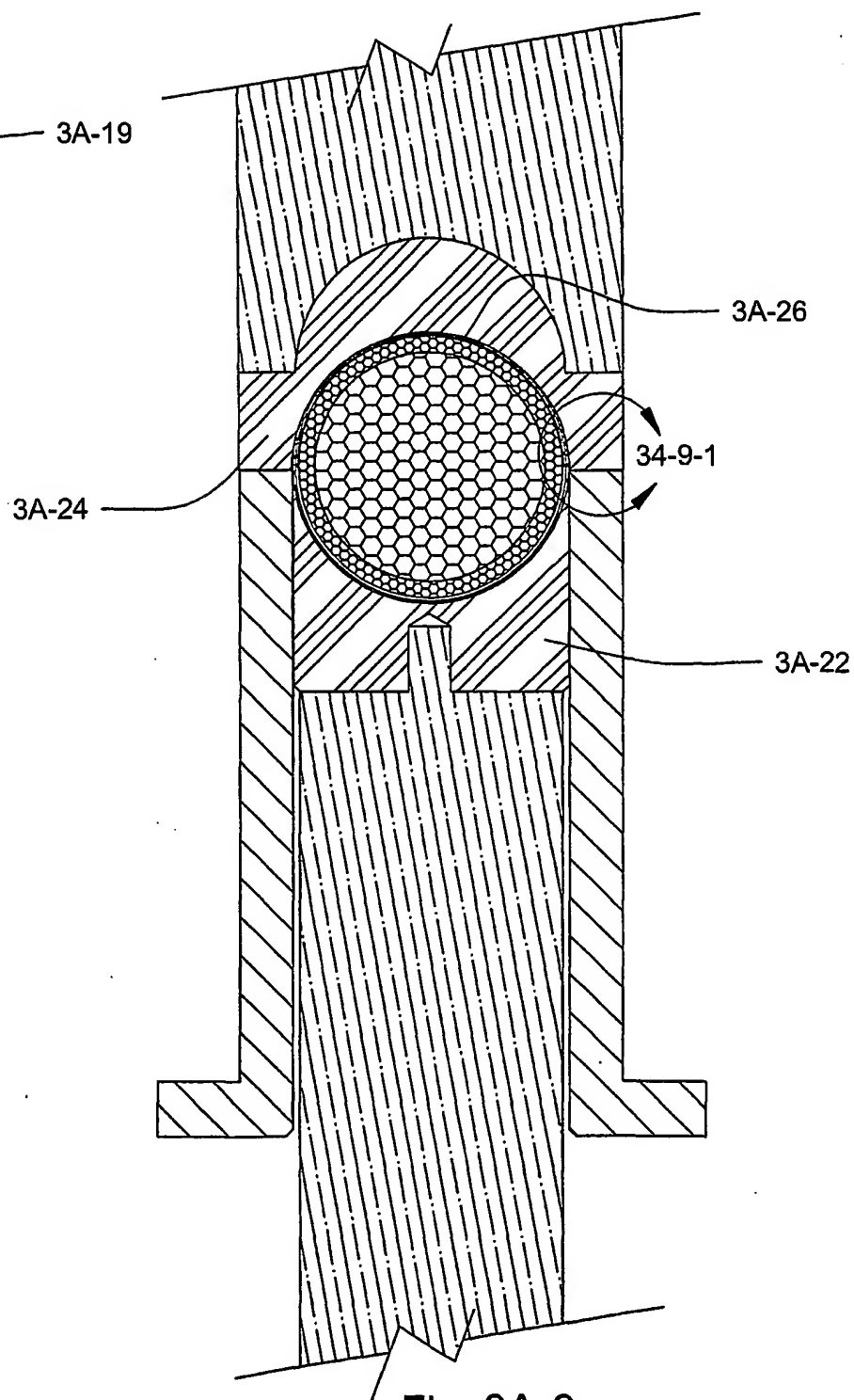


Fig. 3A-9

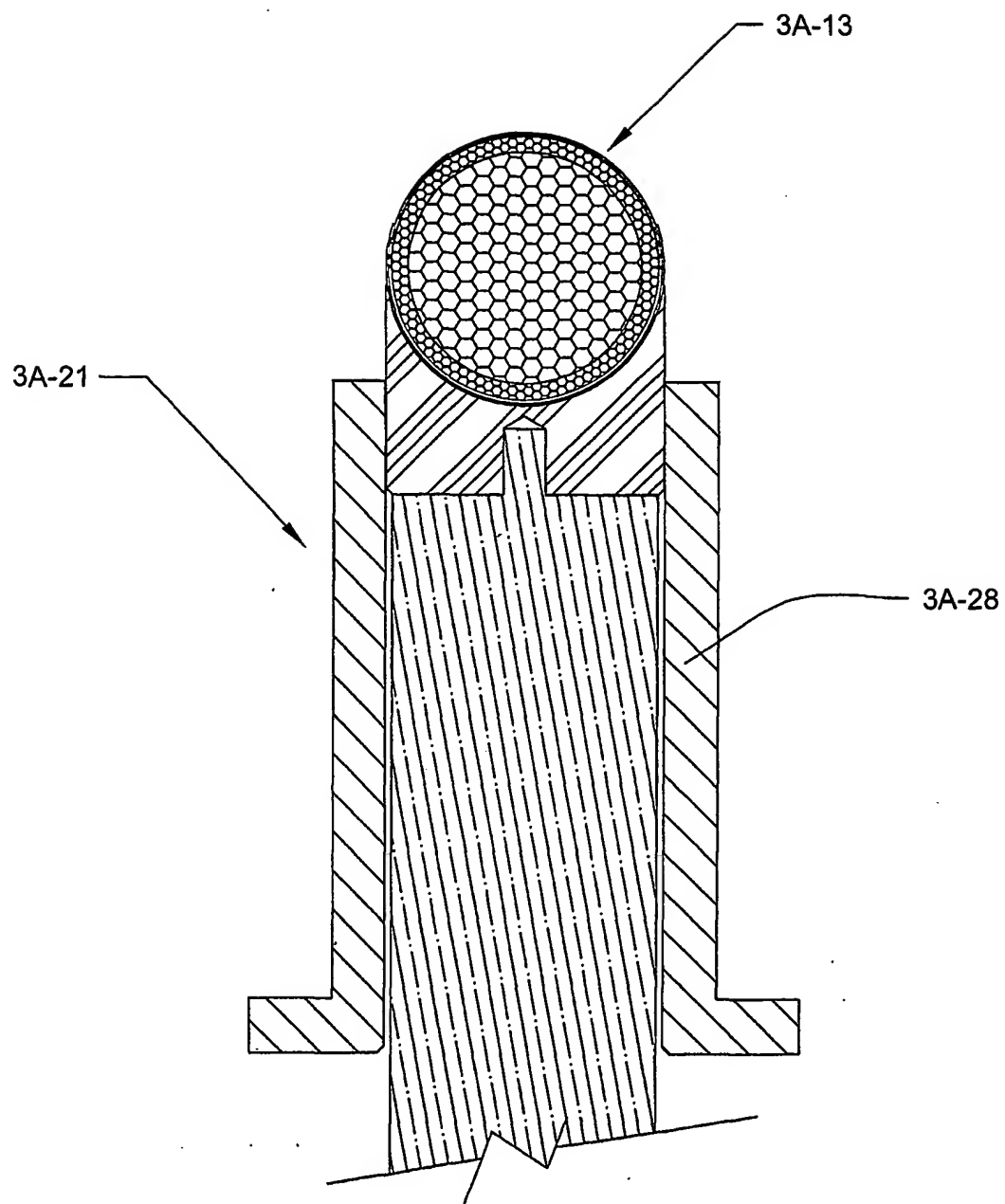


Fig. 3A-10

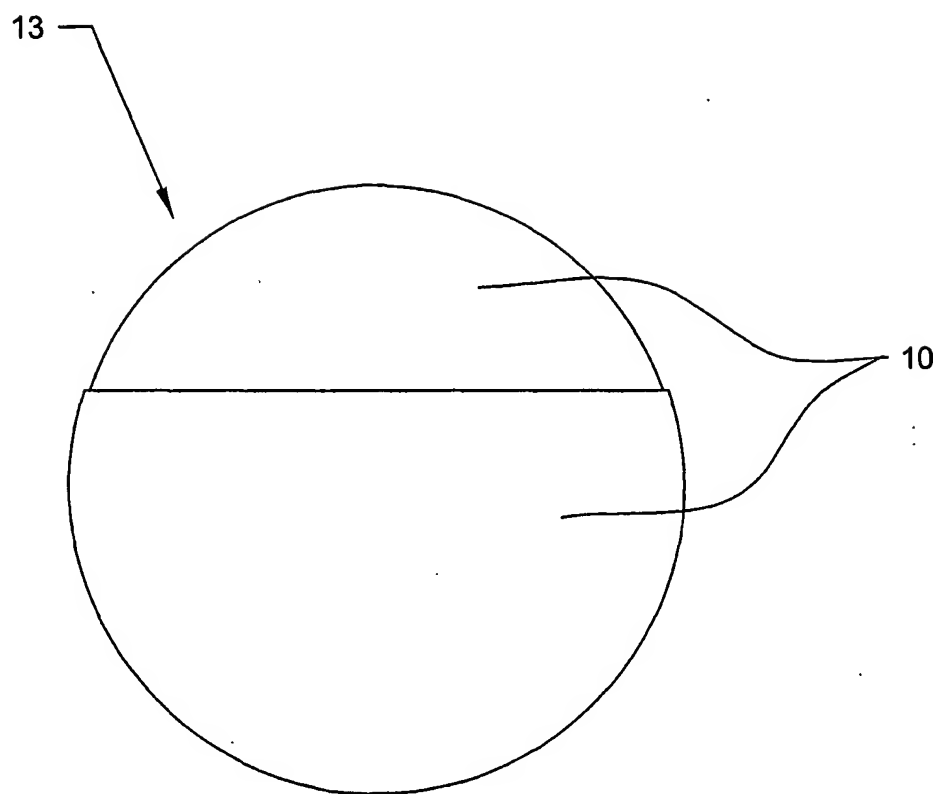


Fig. 3A-11

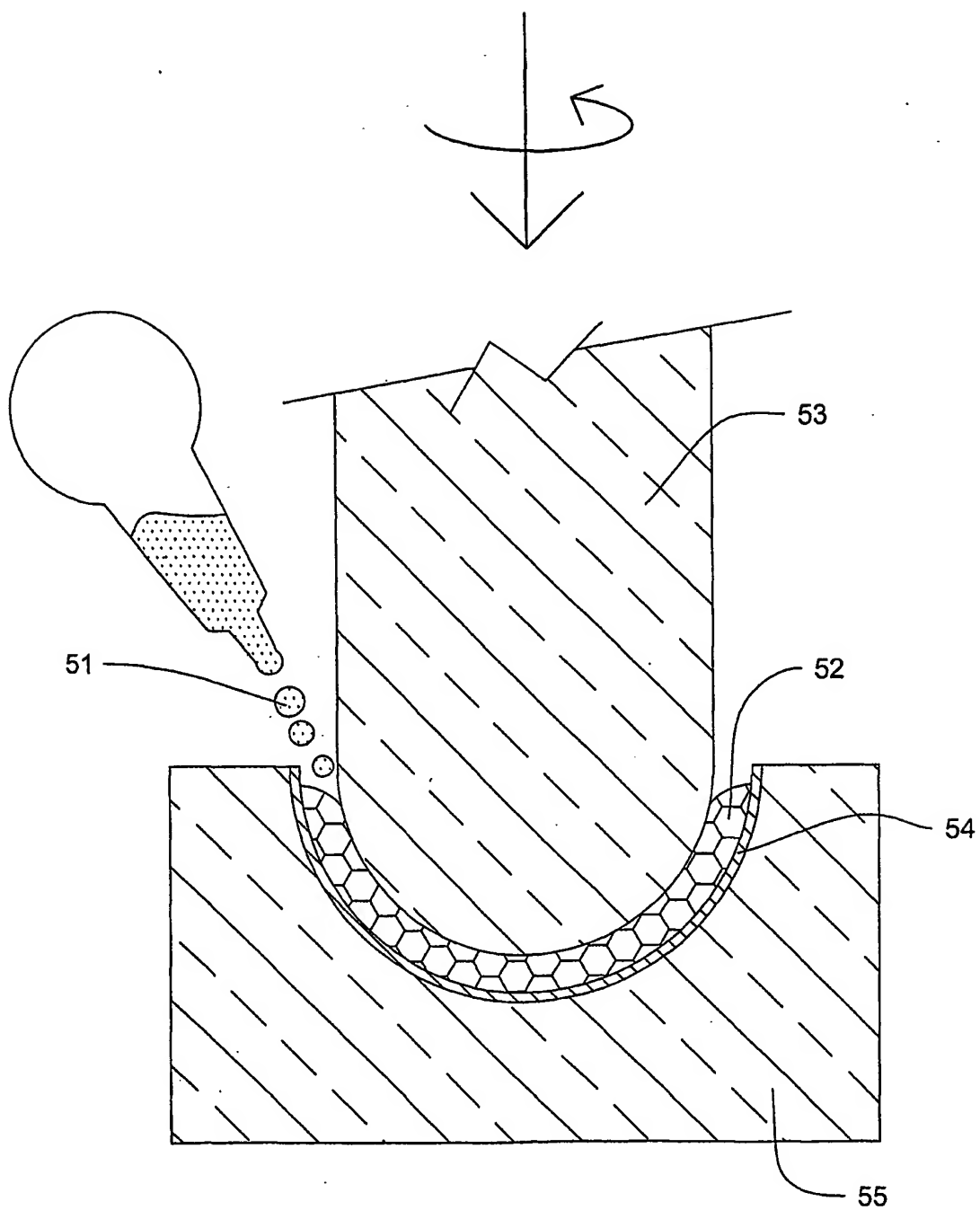


Fig. 5

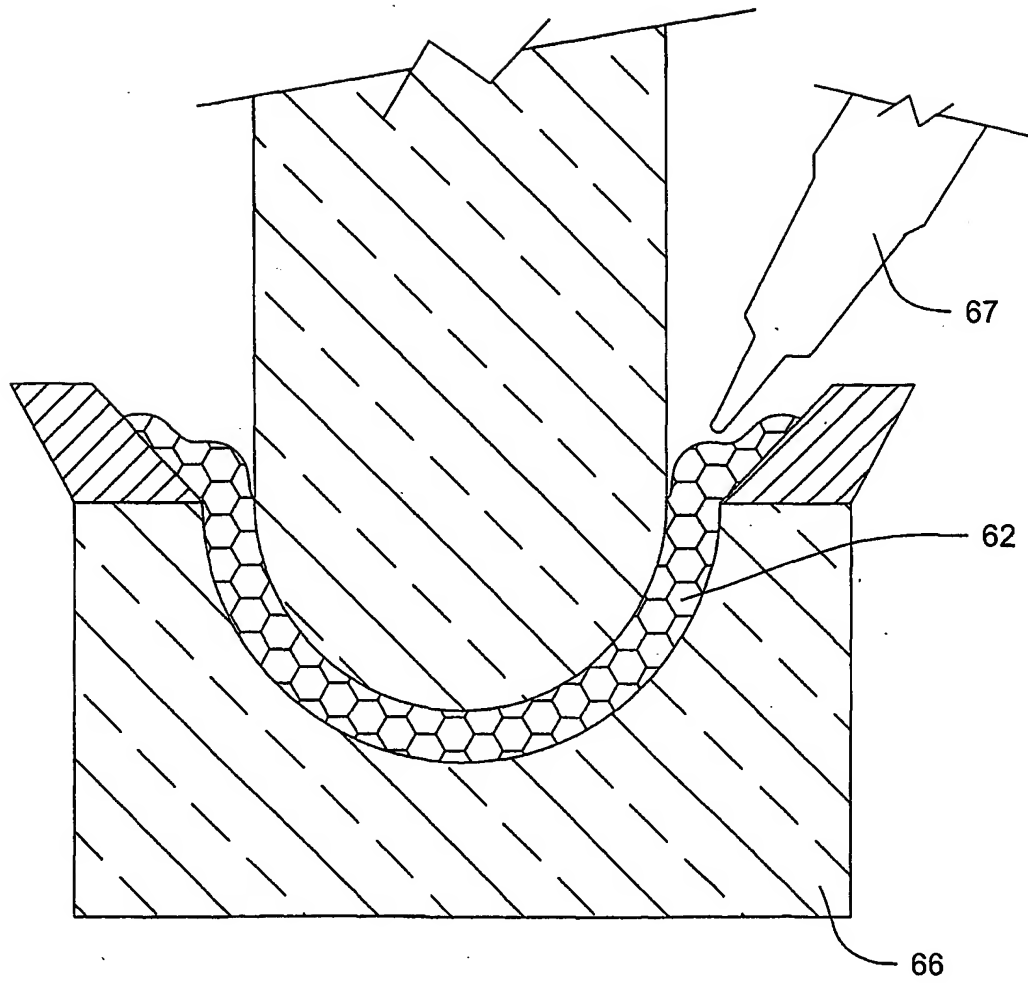


Fig. 6

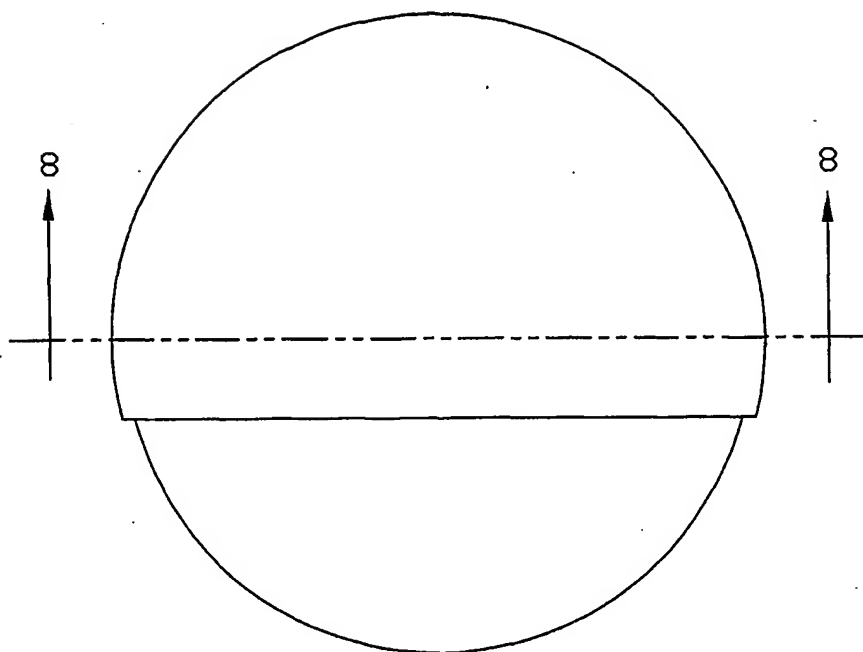


Fig. 7

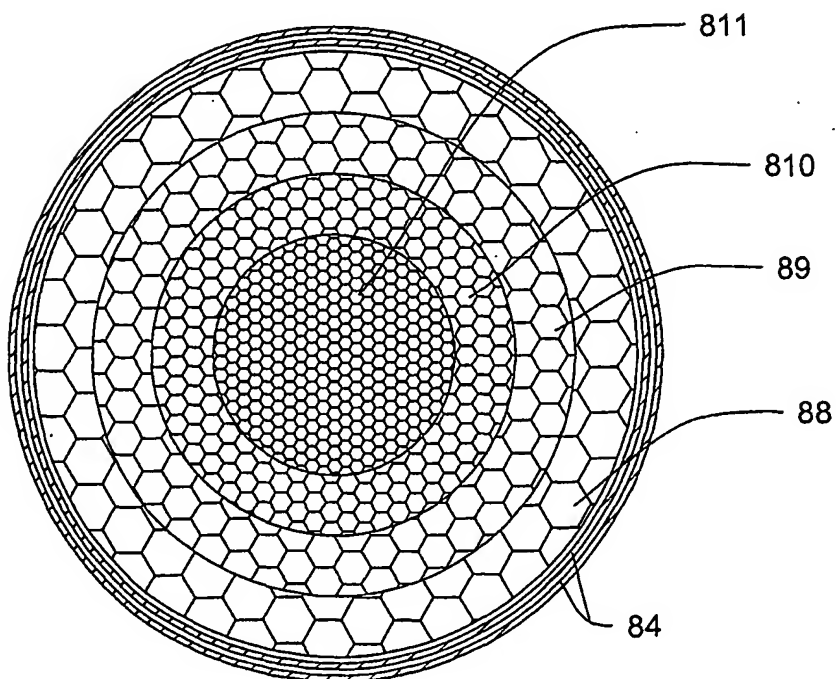


Fig. 8



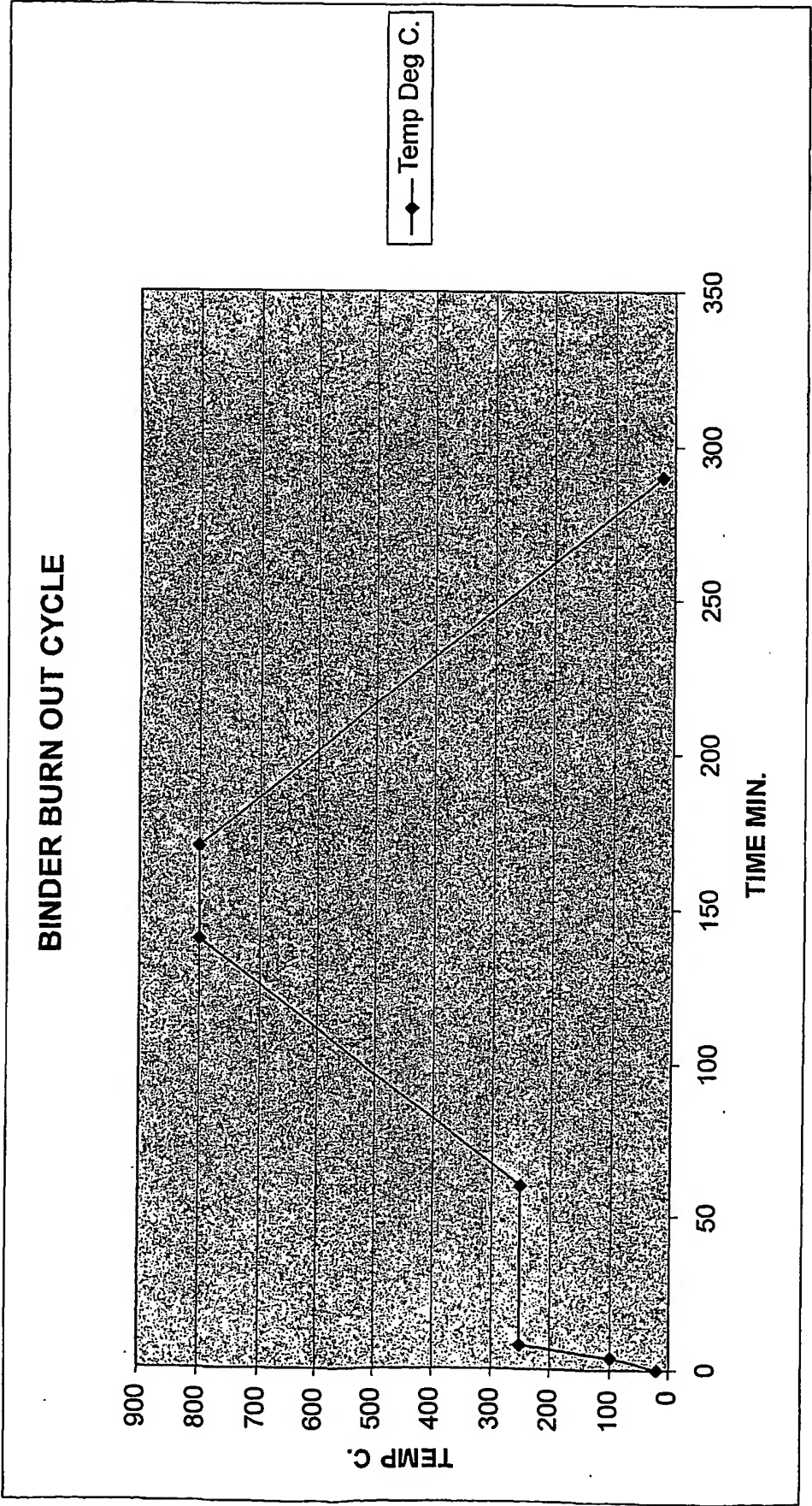


Fig. 9

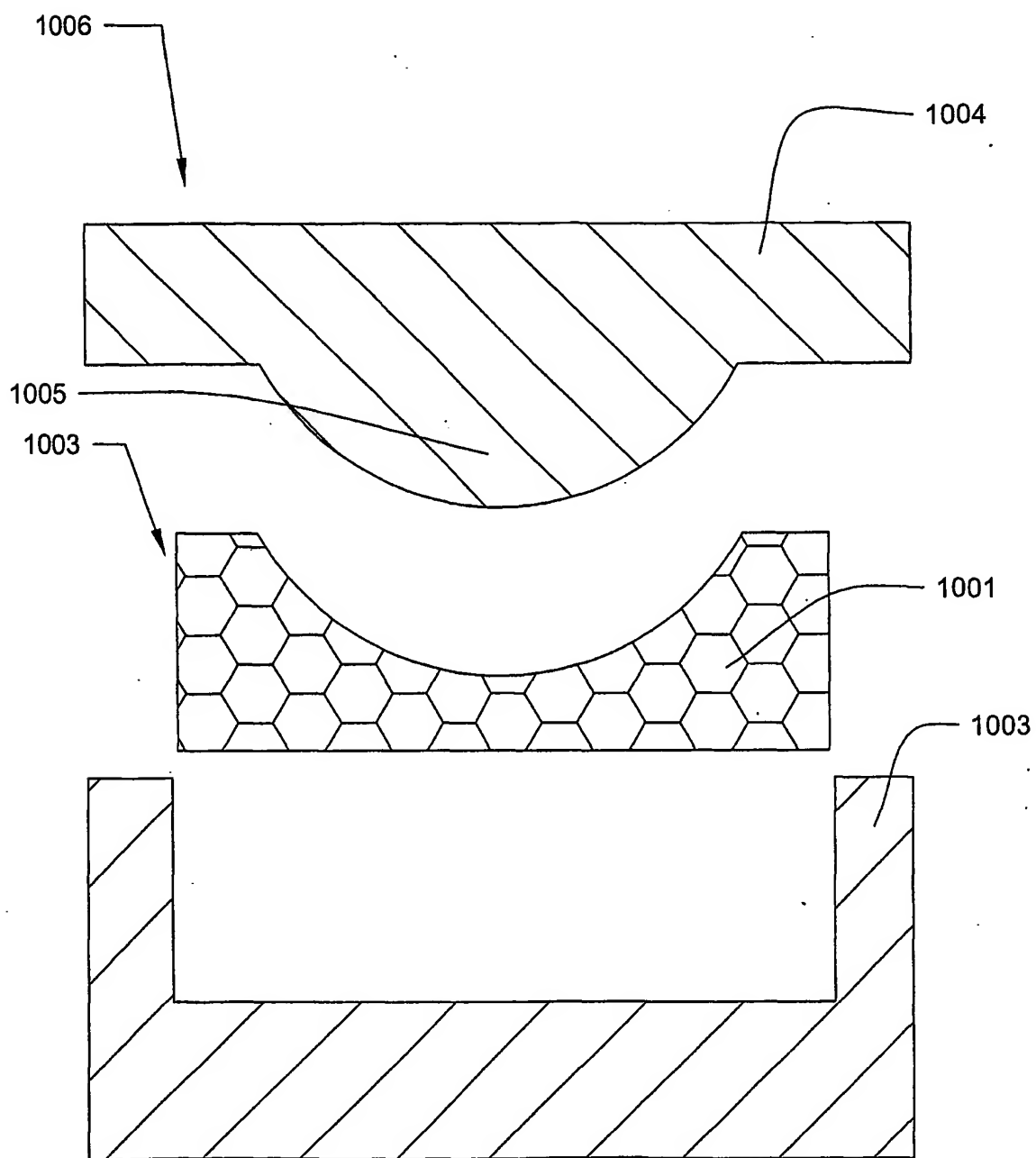


Fig. 10

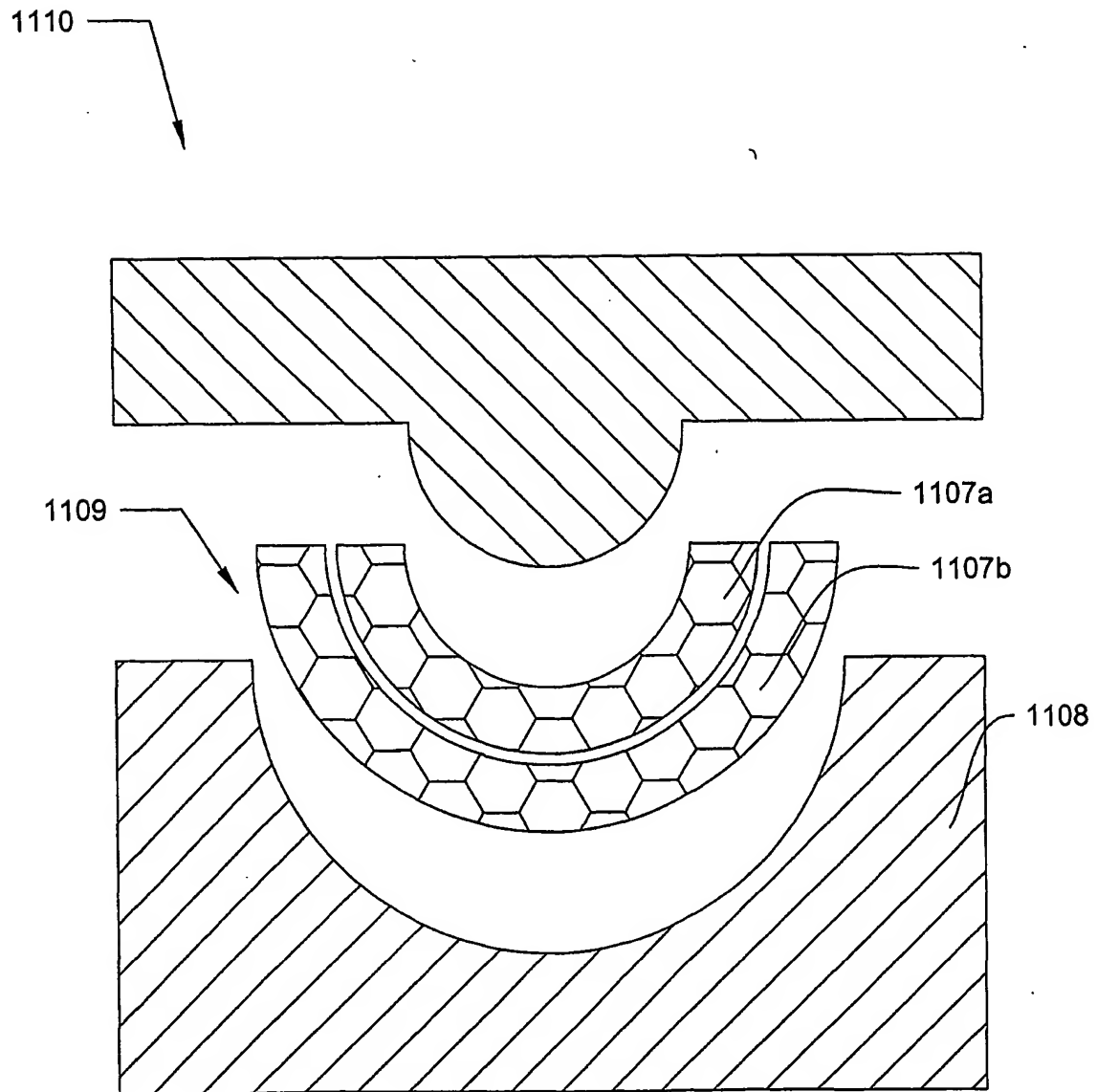


Fig. 11

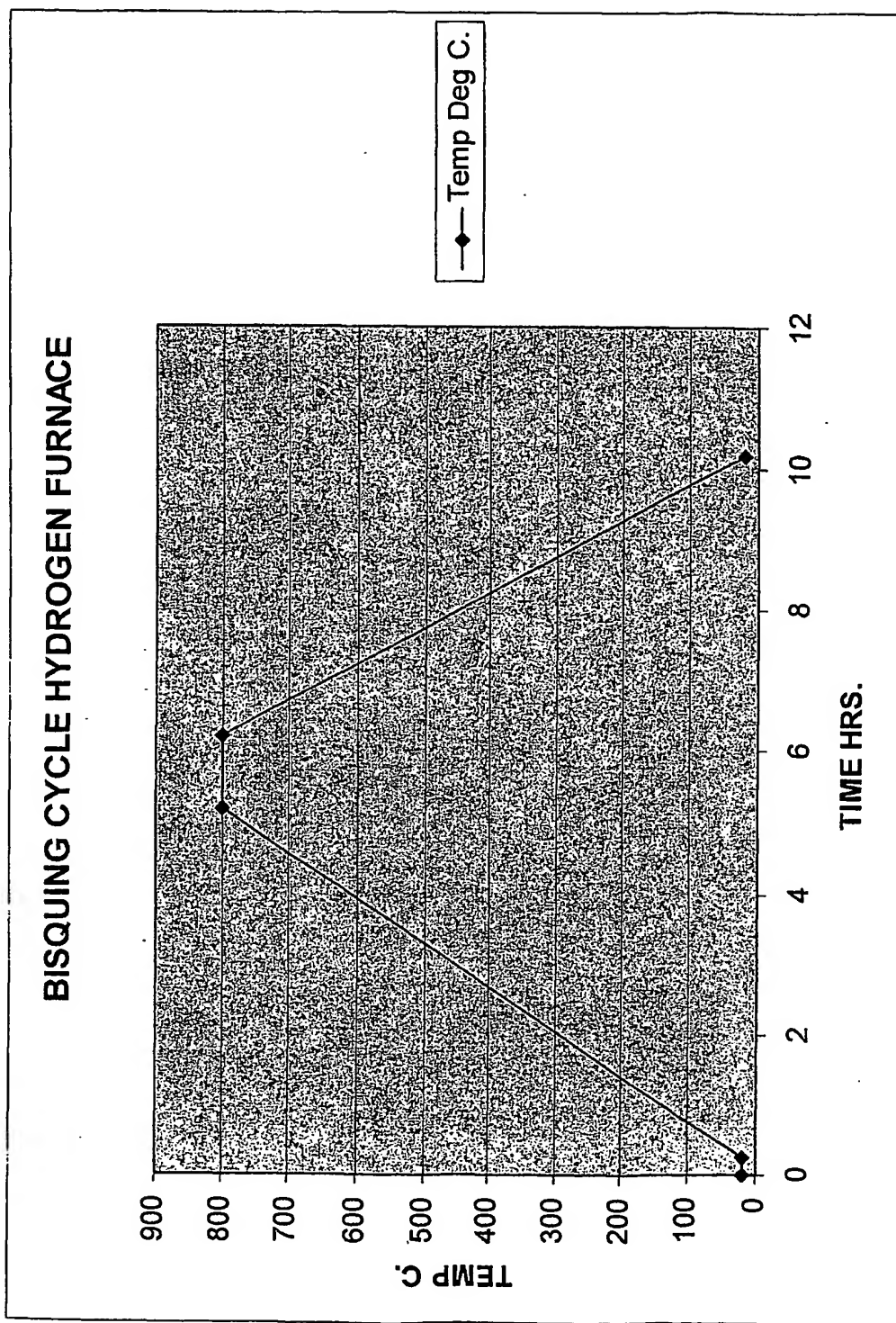


Fig. 12

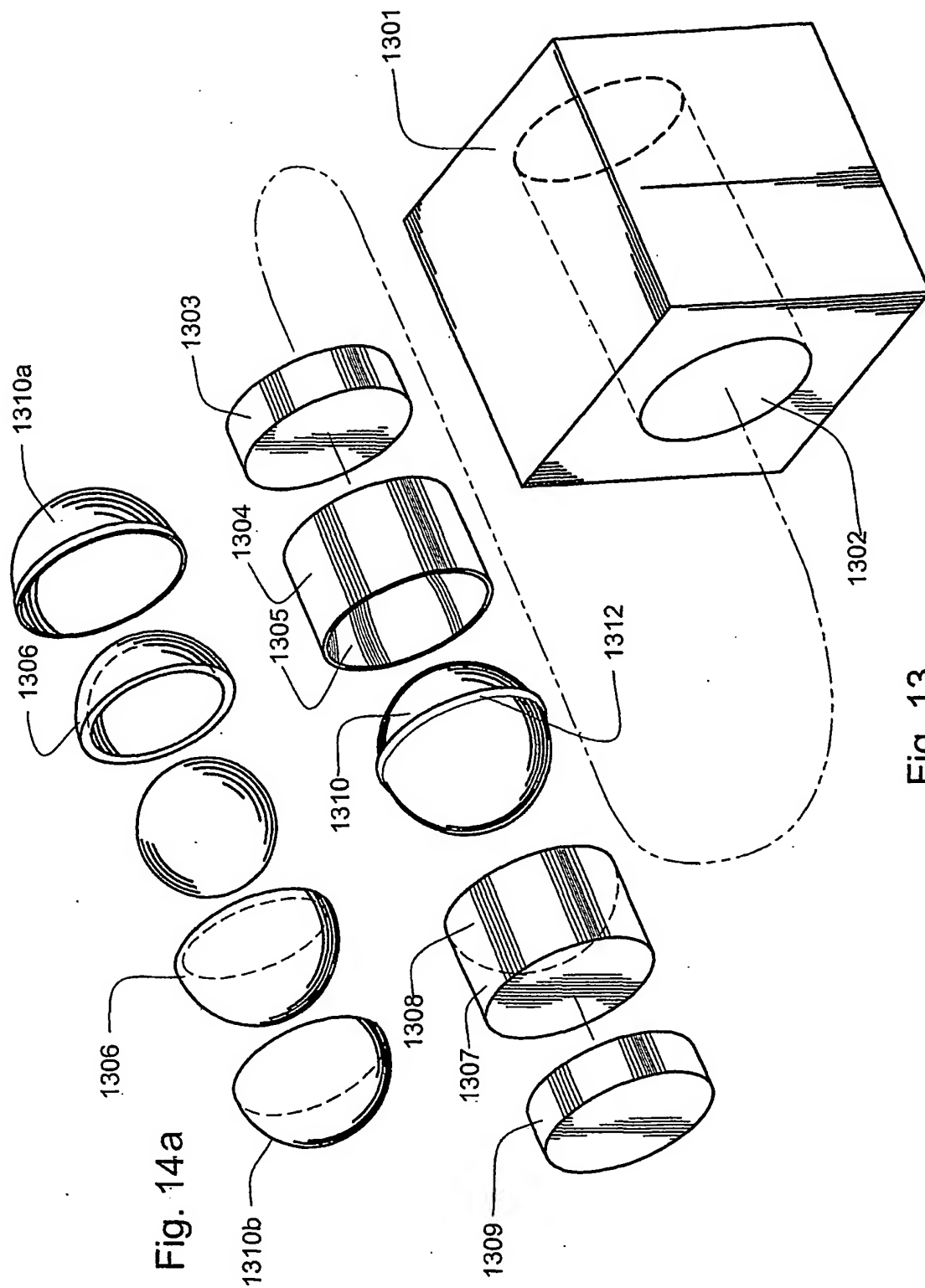


Fig. 13

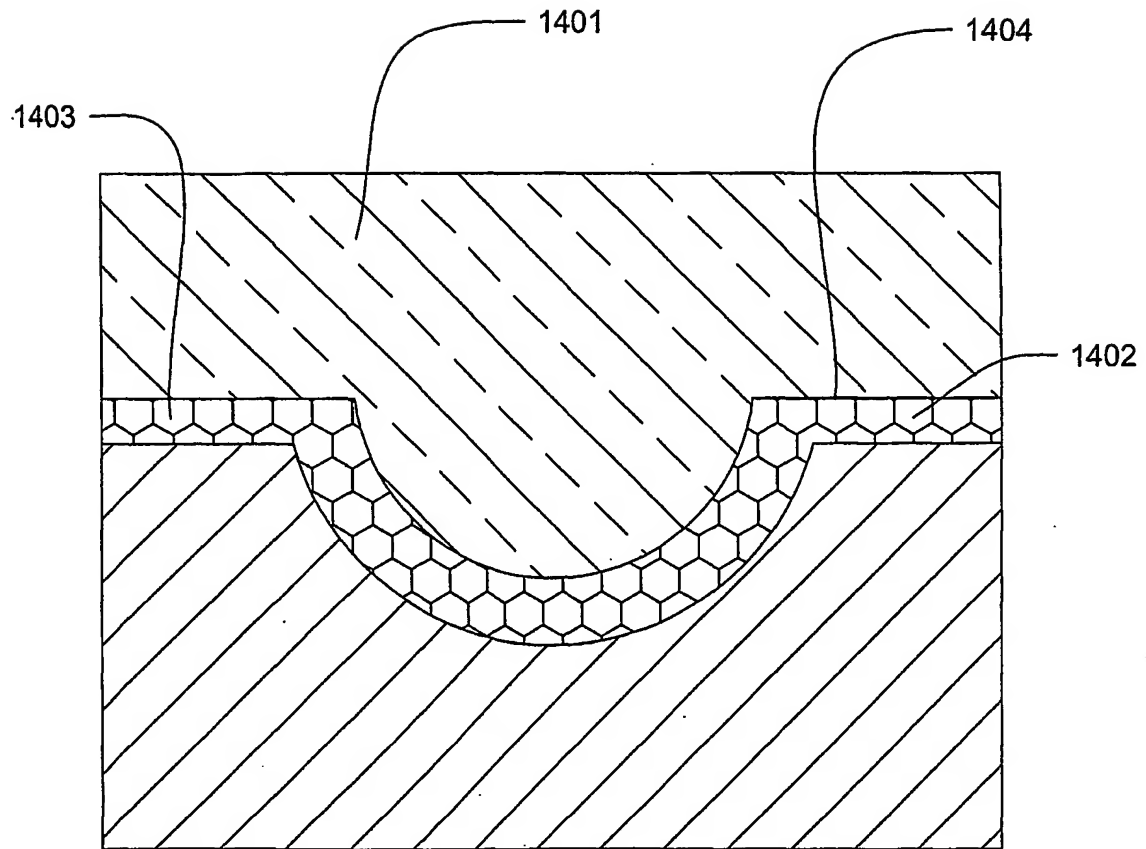


Fig. 14

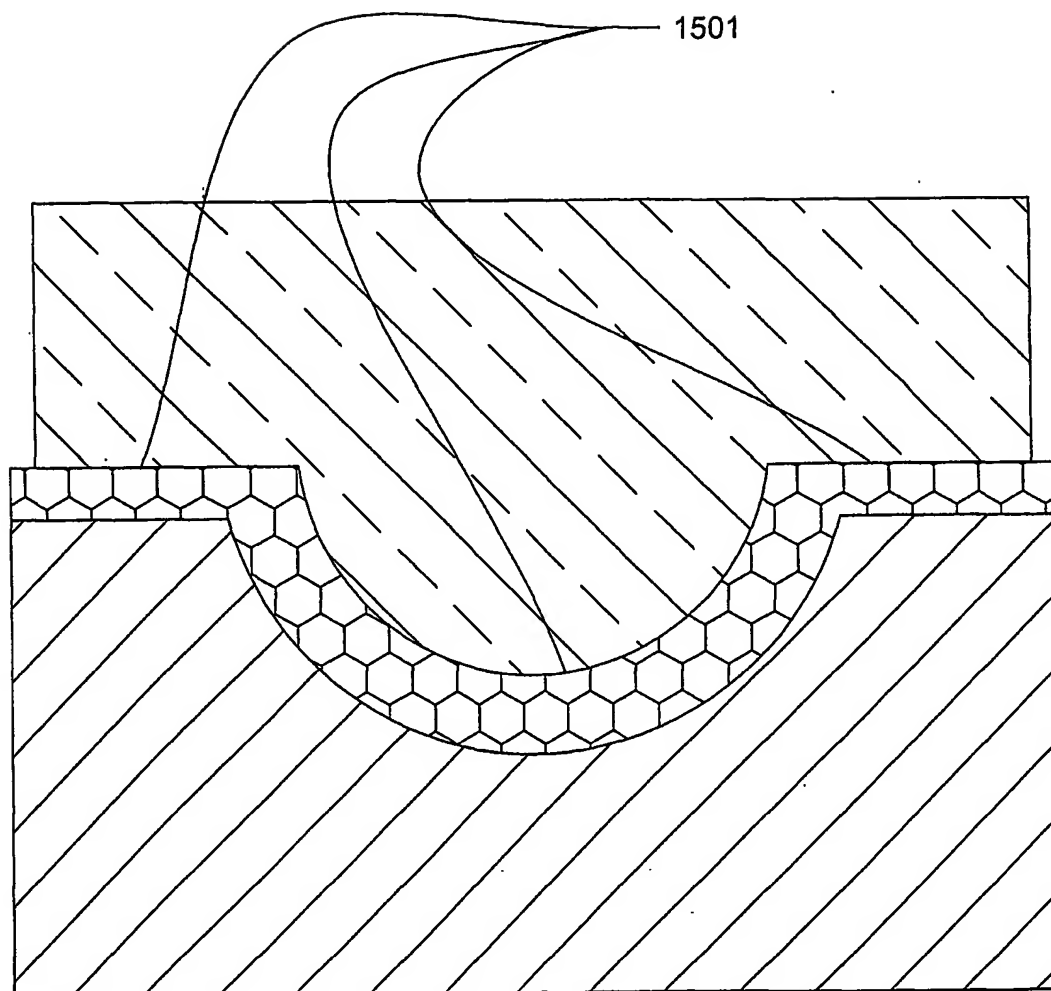


Fig. 15

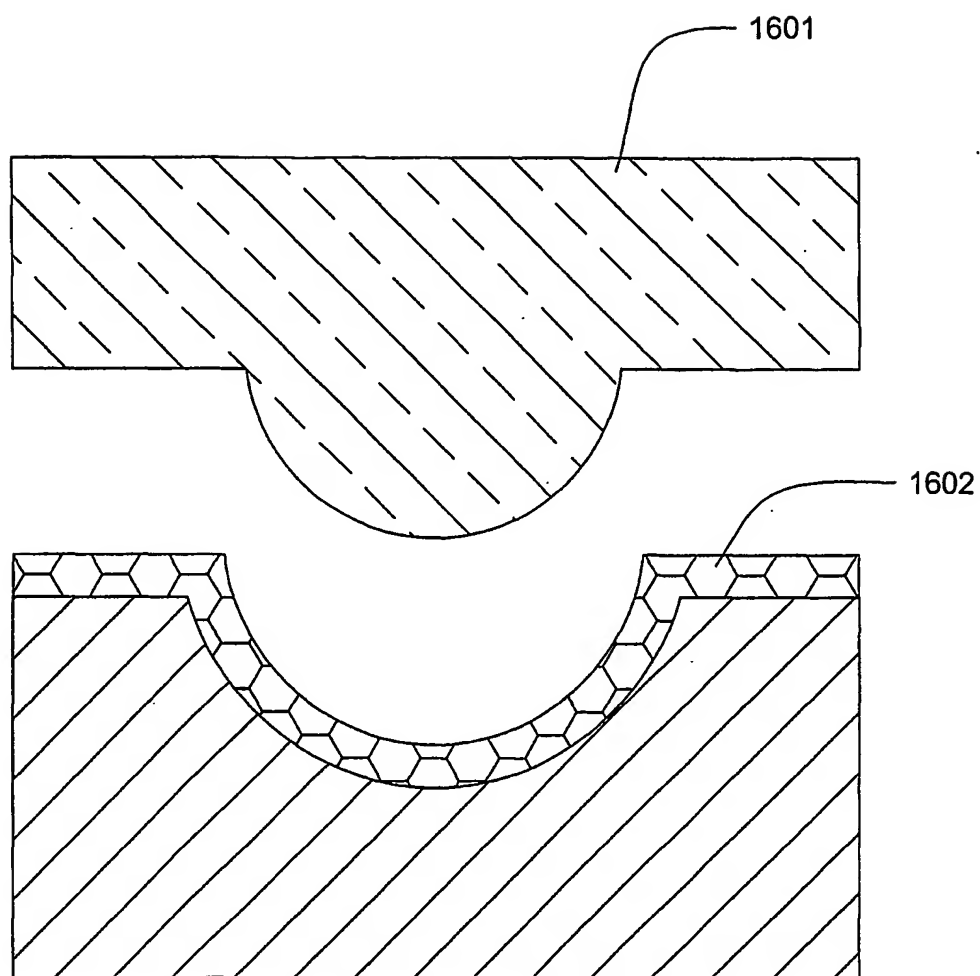


Fig. 16



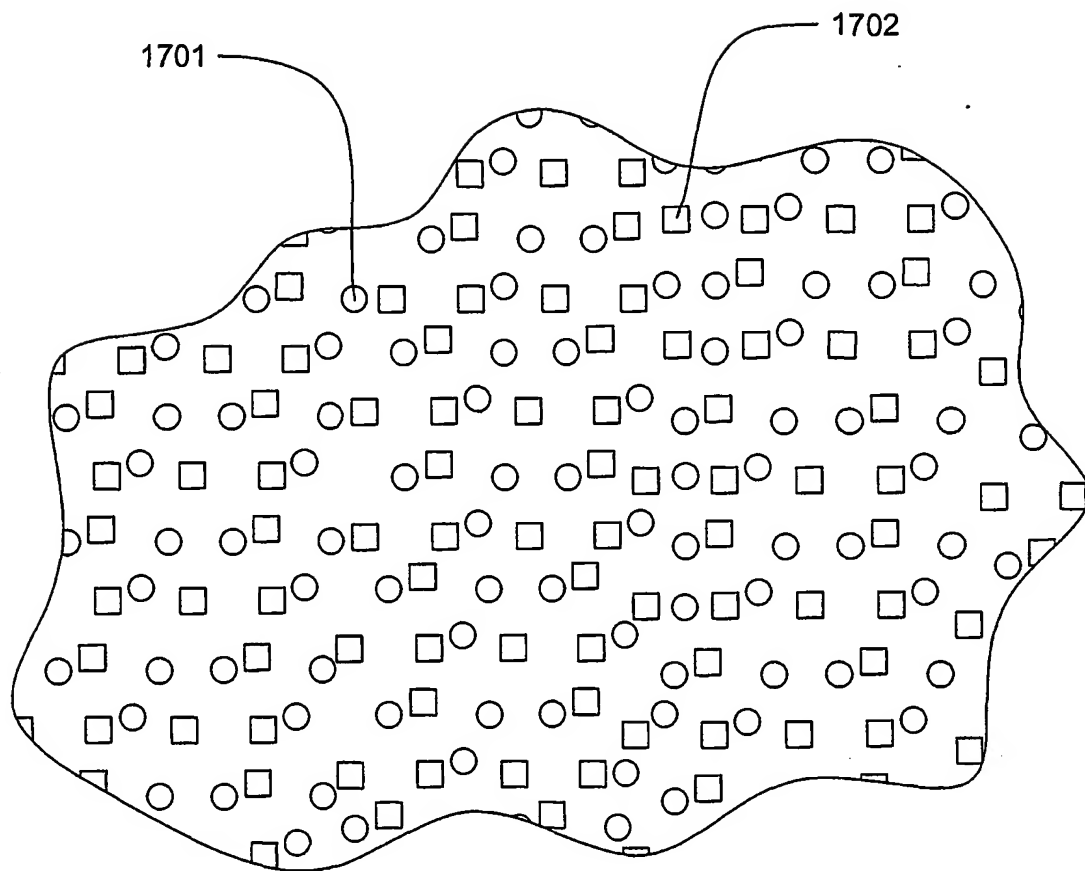


Fig. 17

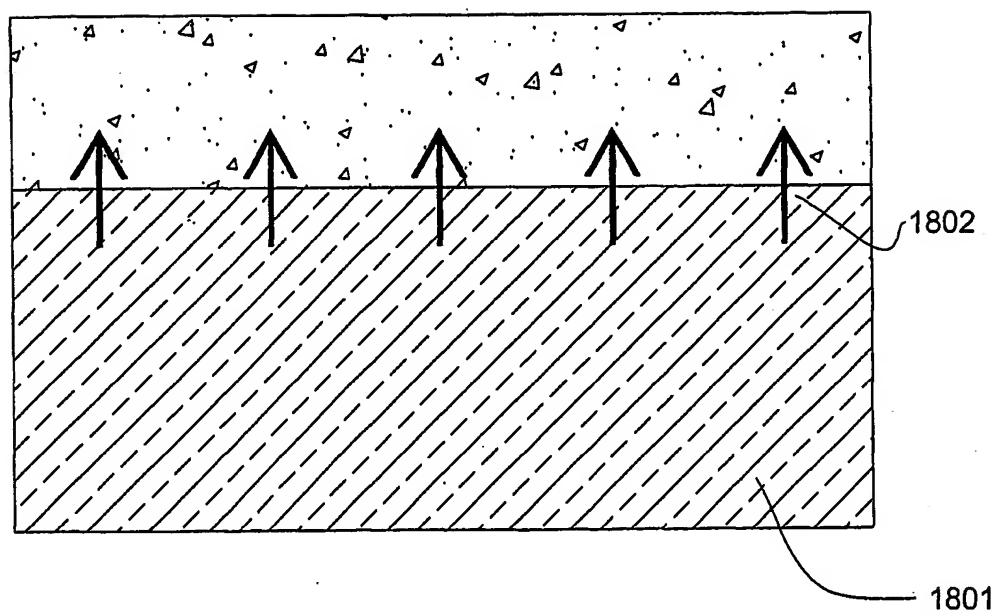


Fig. 18

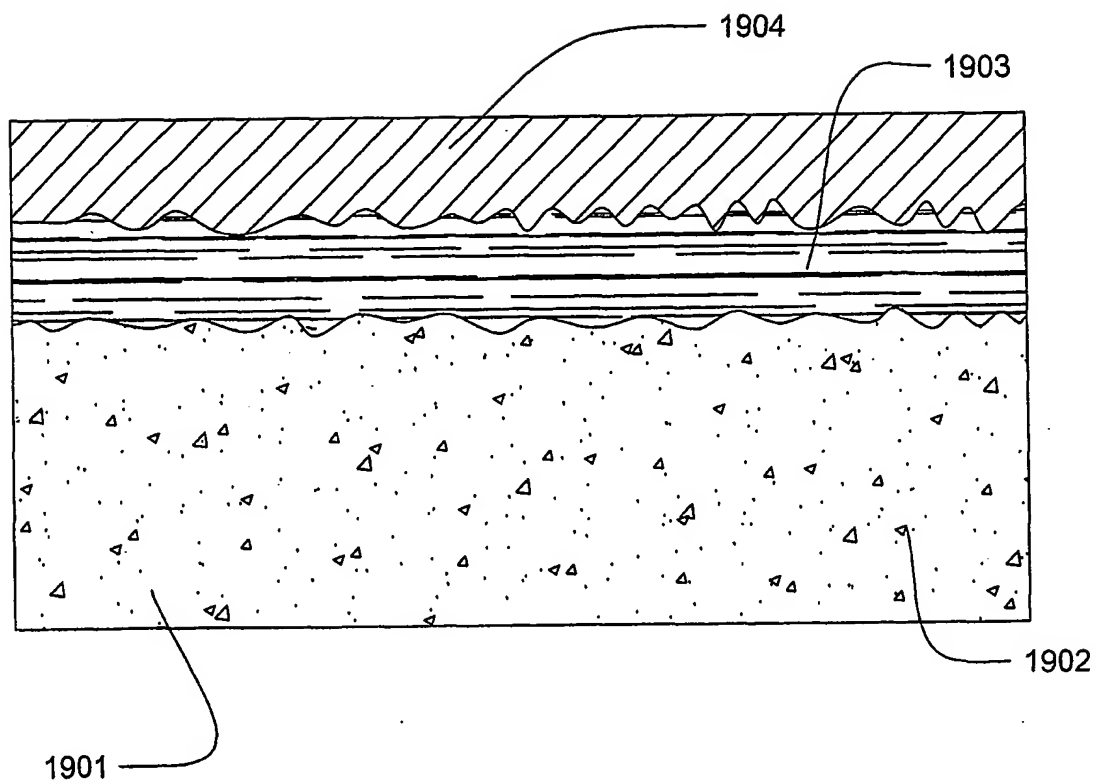


Fig. 19

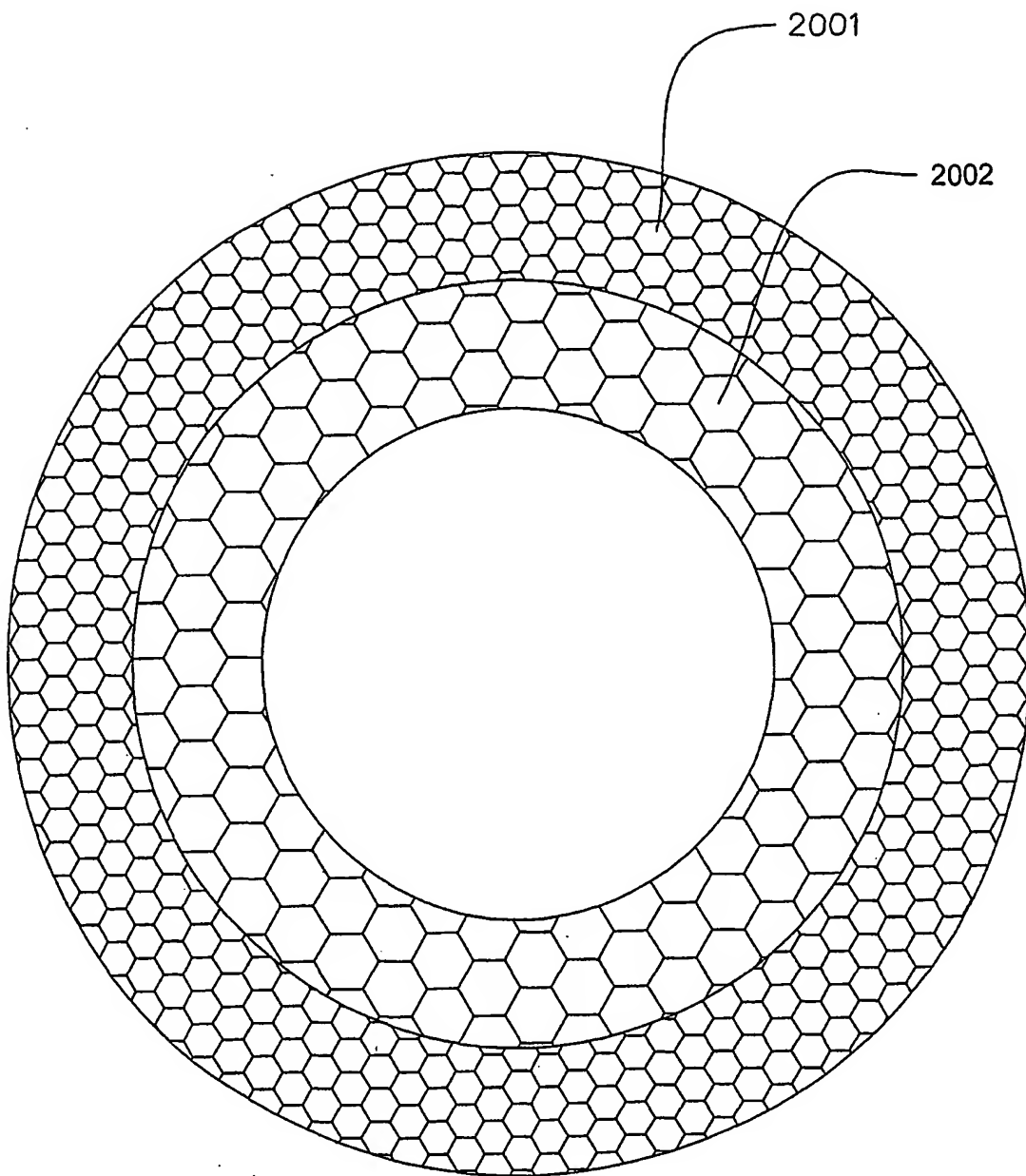


Fig. 20

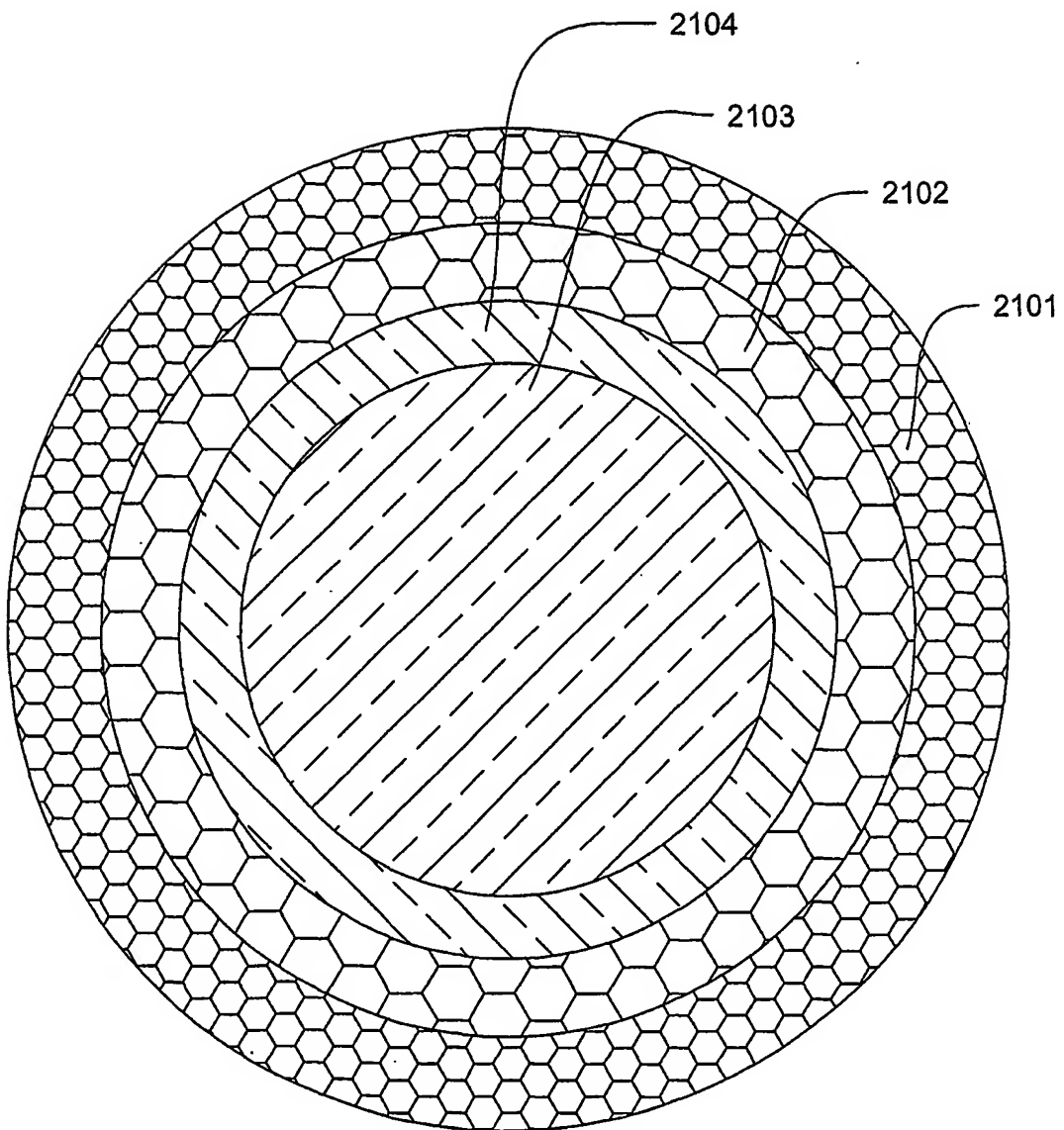


Fig. 21

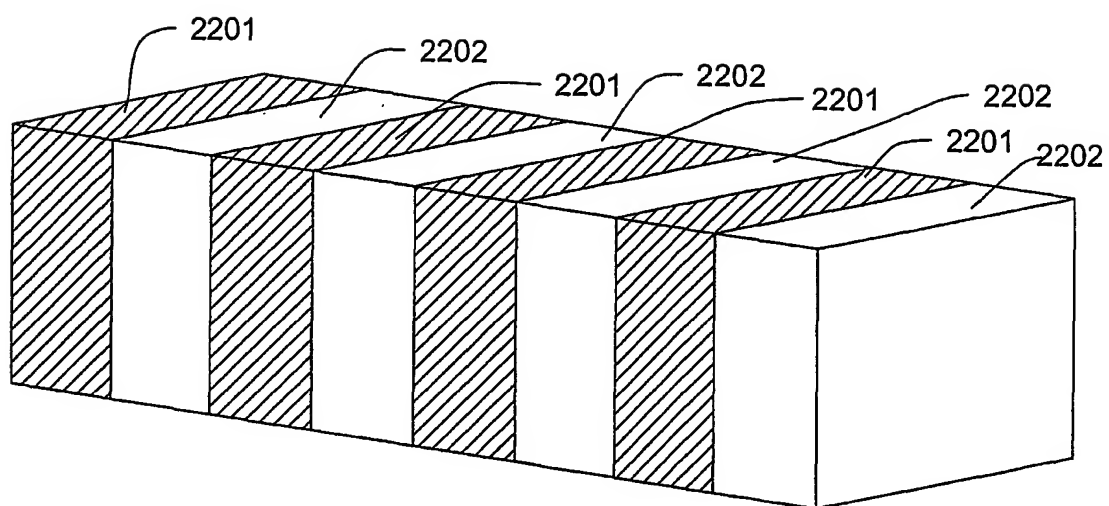


Fig. 22

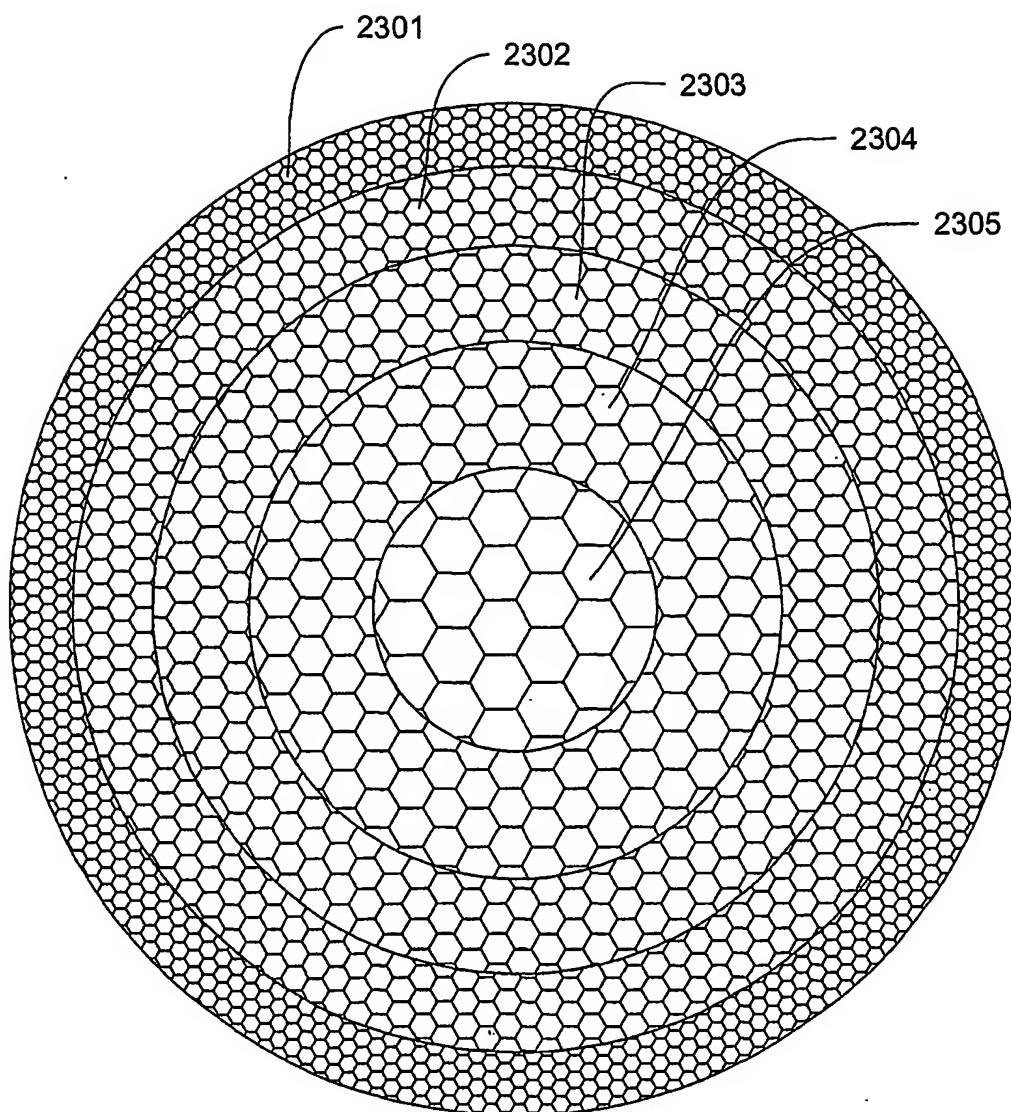


Fig. 23

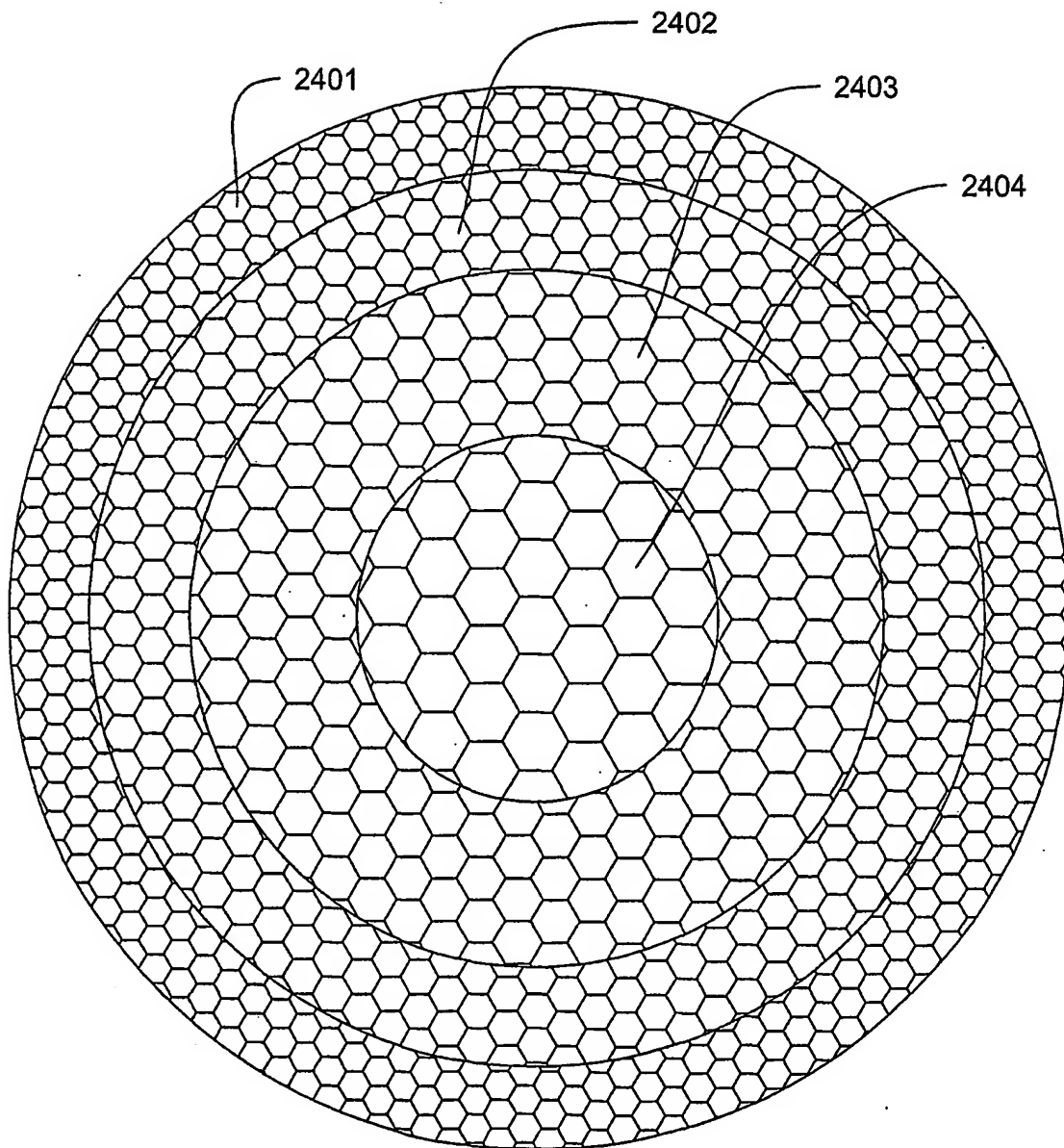


Fig. 24



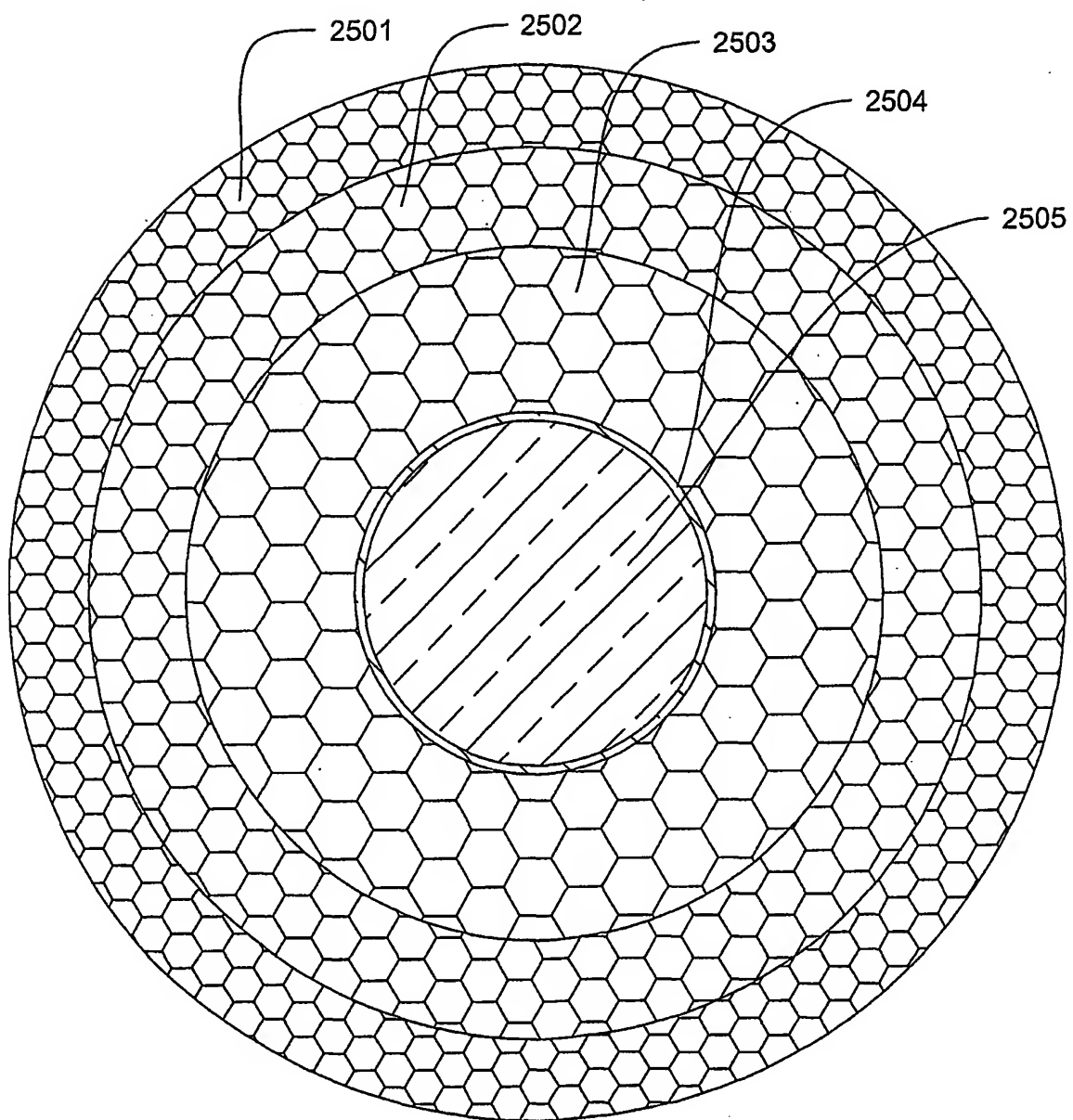


Fig. 25

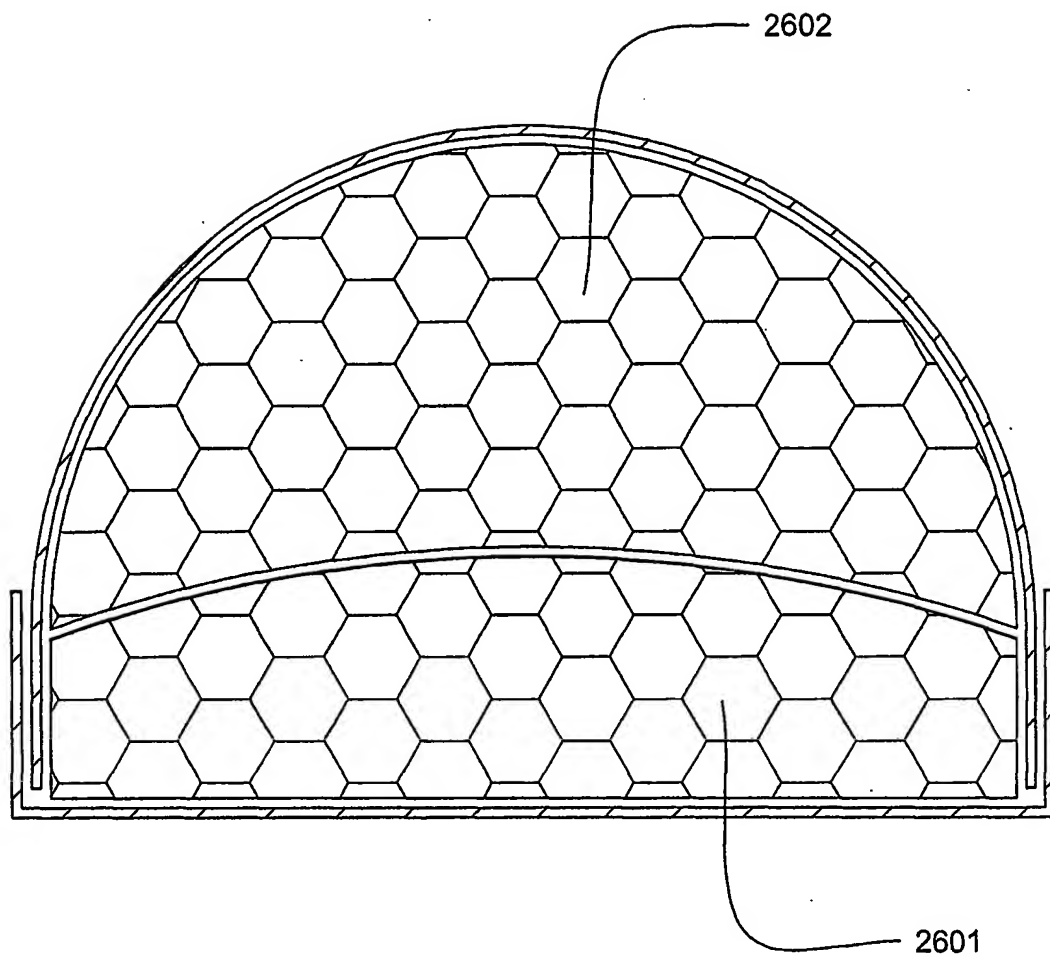


Fig. 26

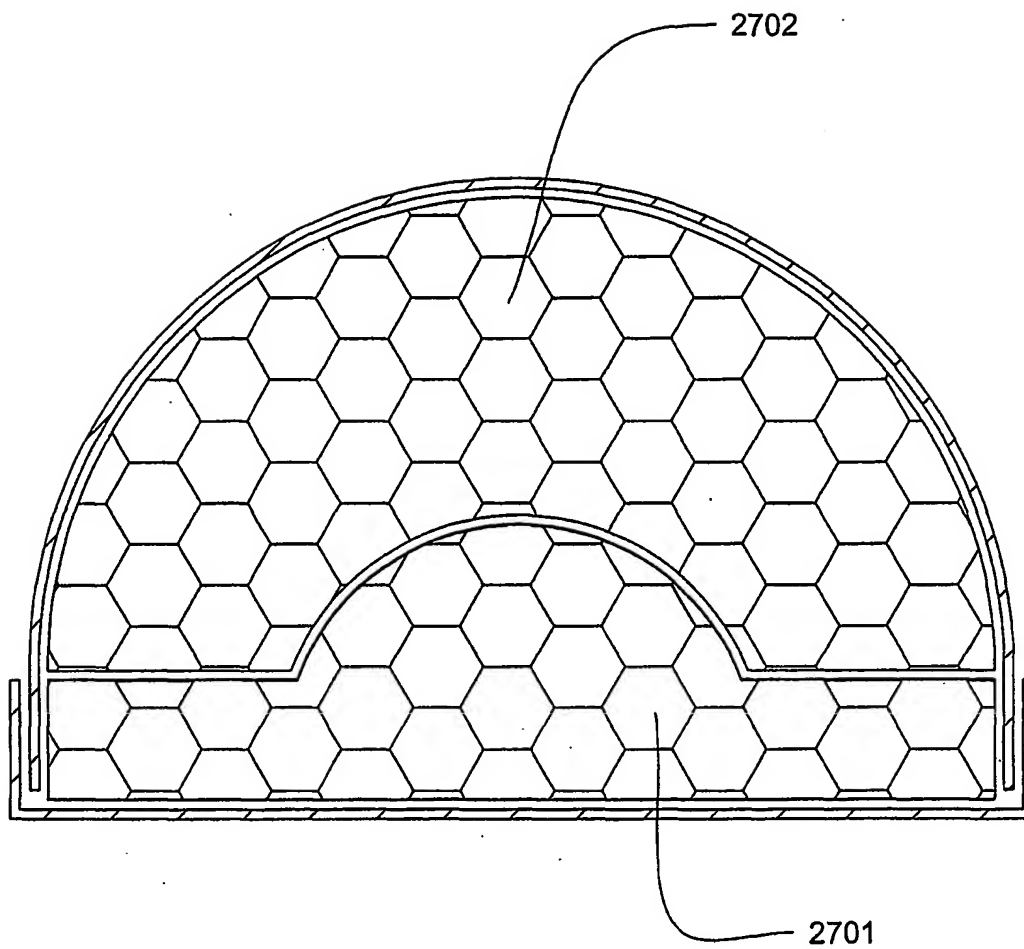


Fig. 27

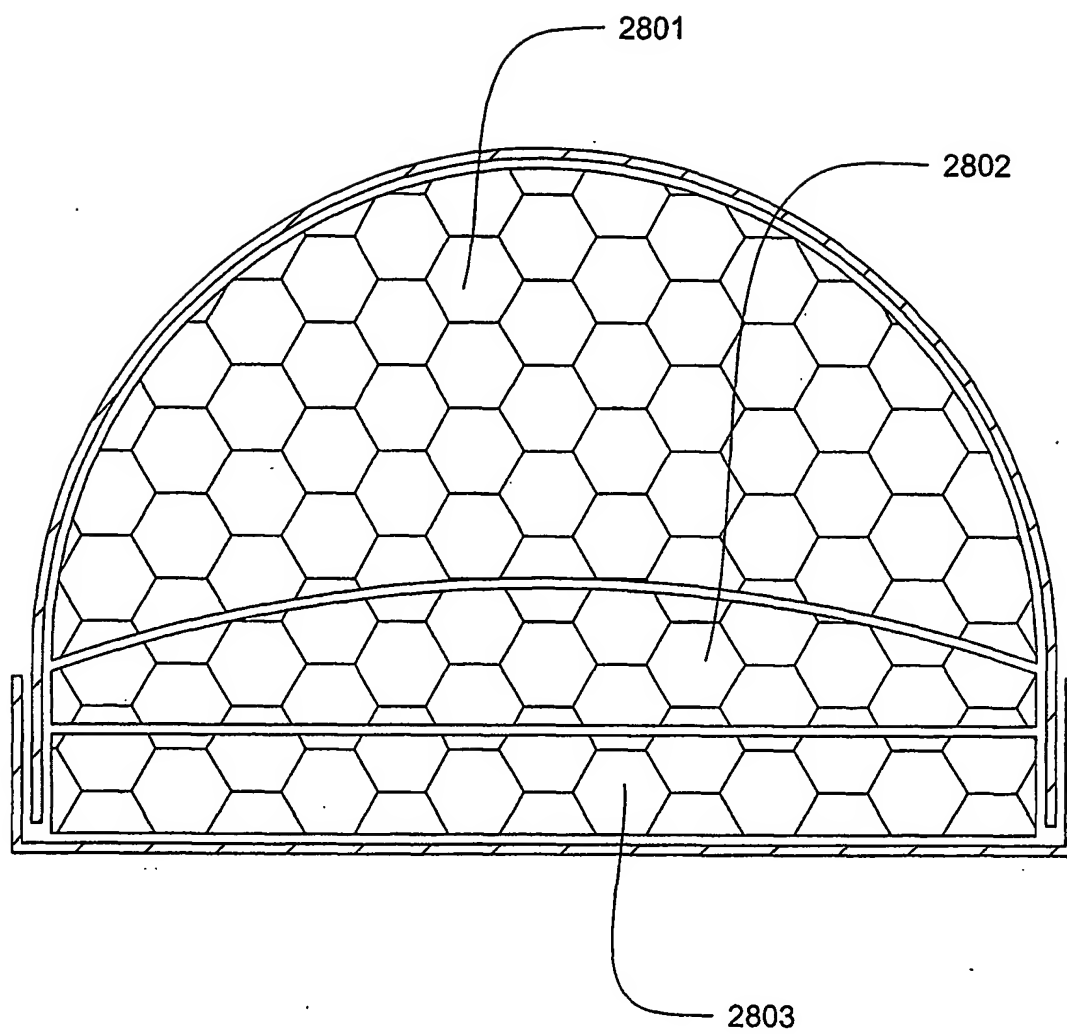


Fig. 28

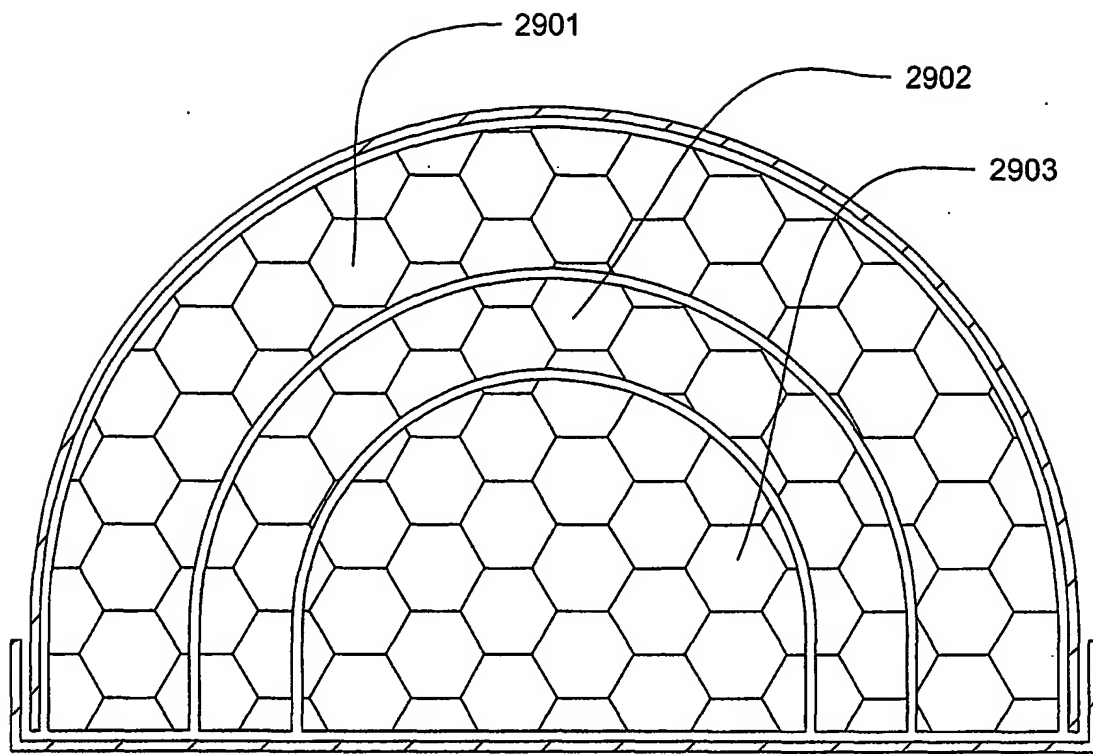


Fig. 29

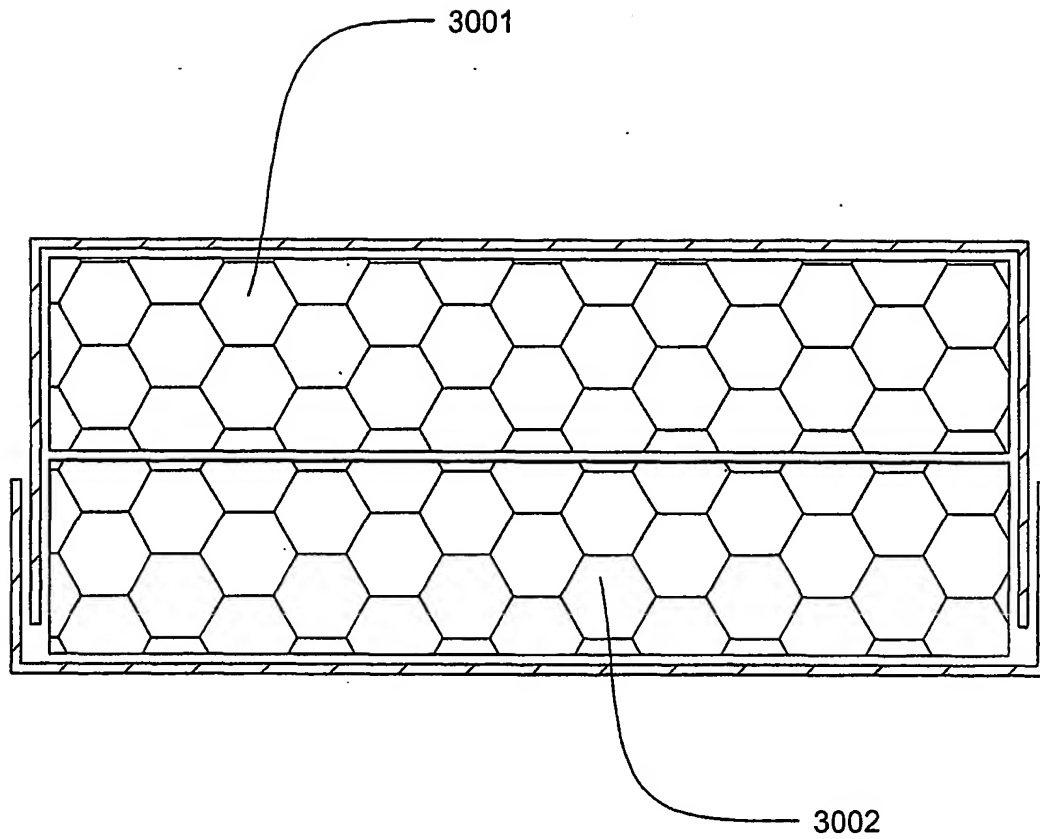


Fig. 30

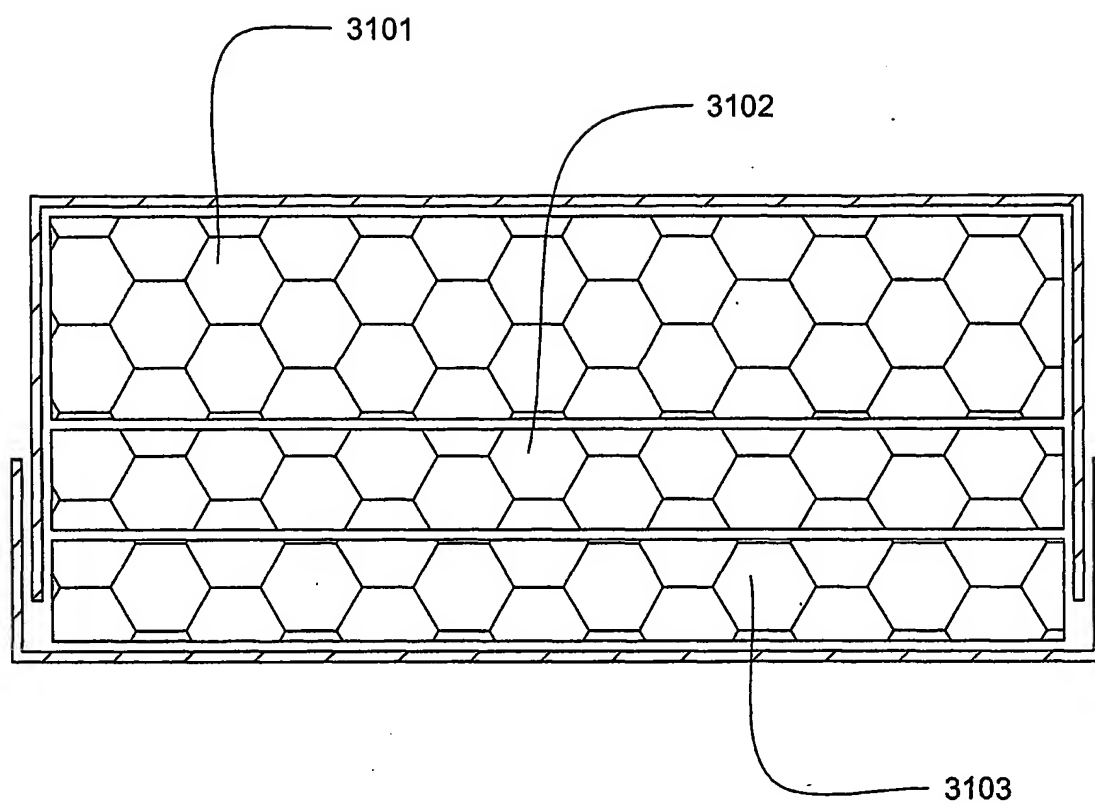


Fig. 31

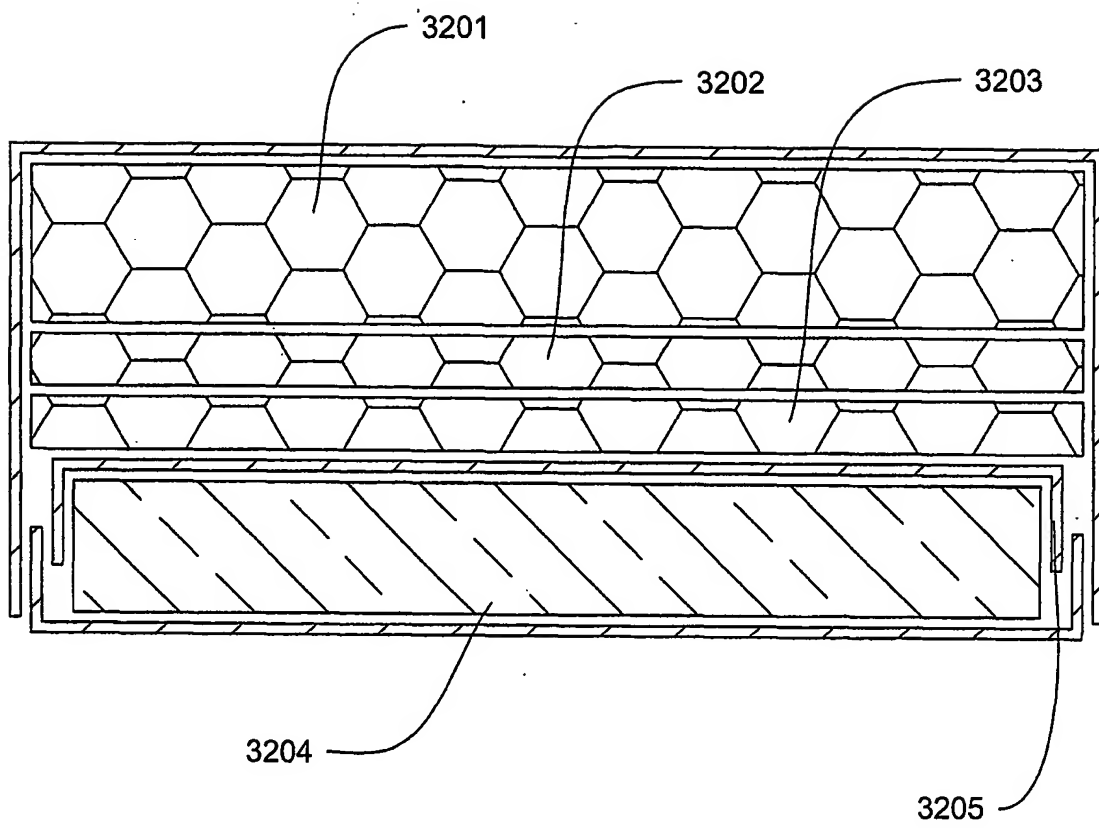


Fig. 32



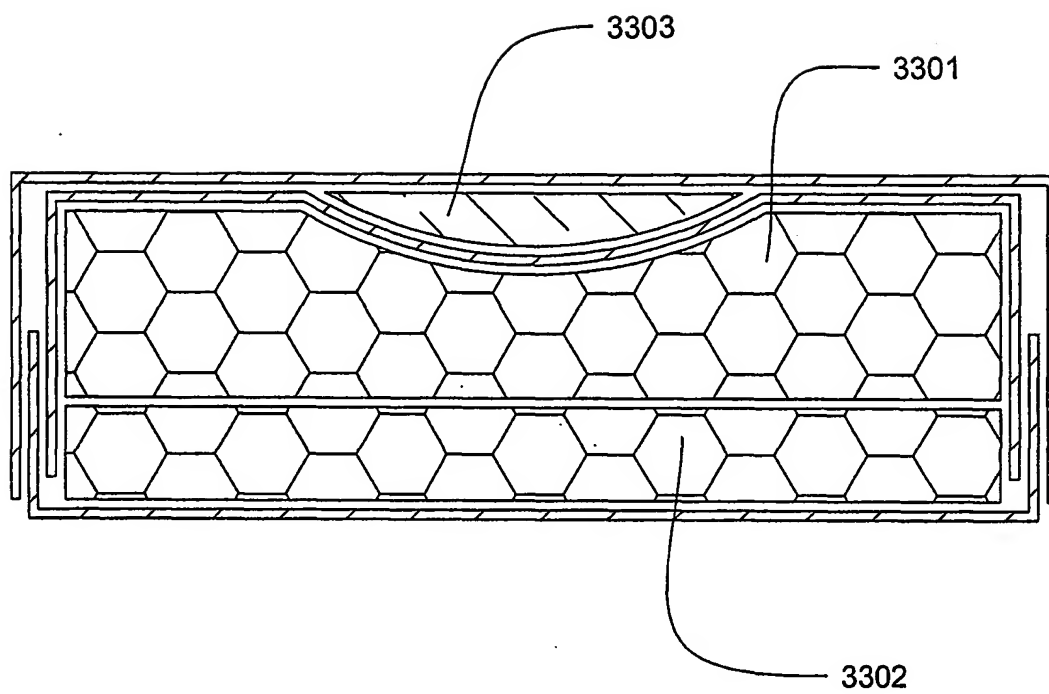


Fig. 33

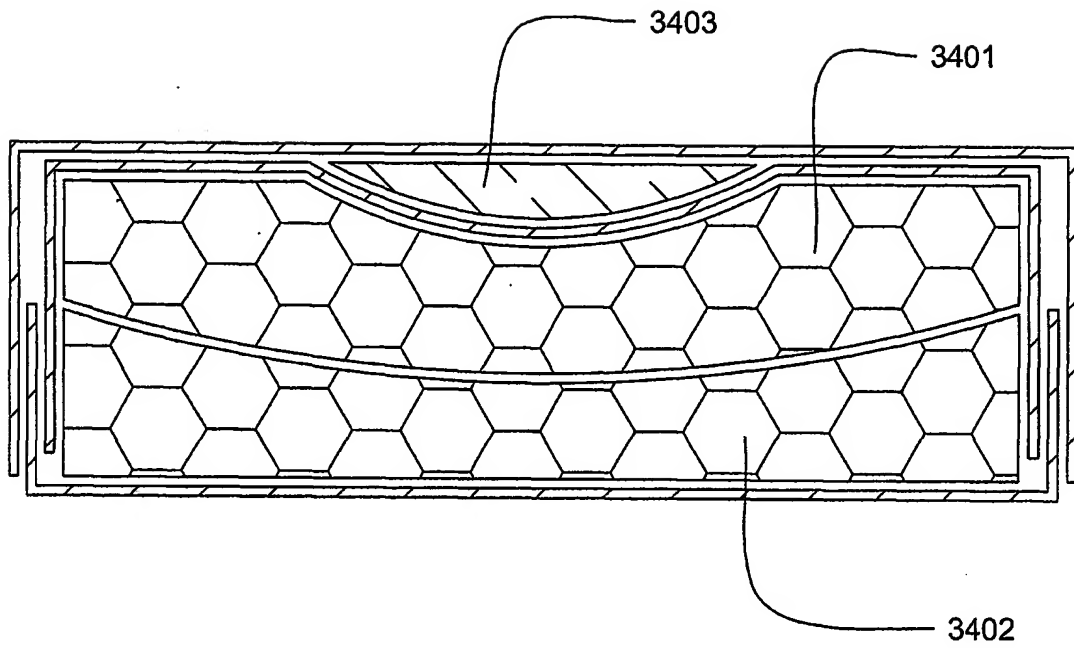


Fig. 34

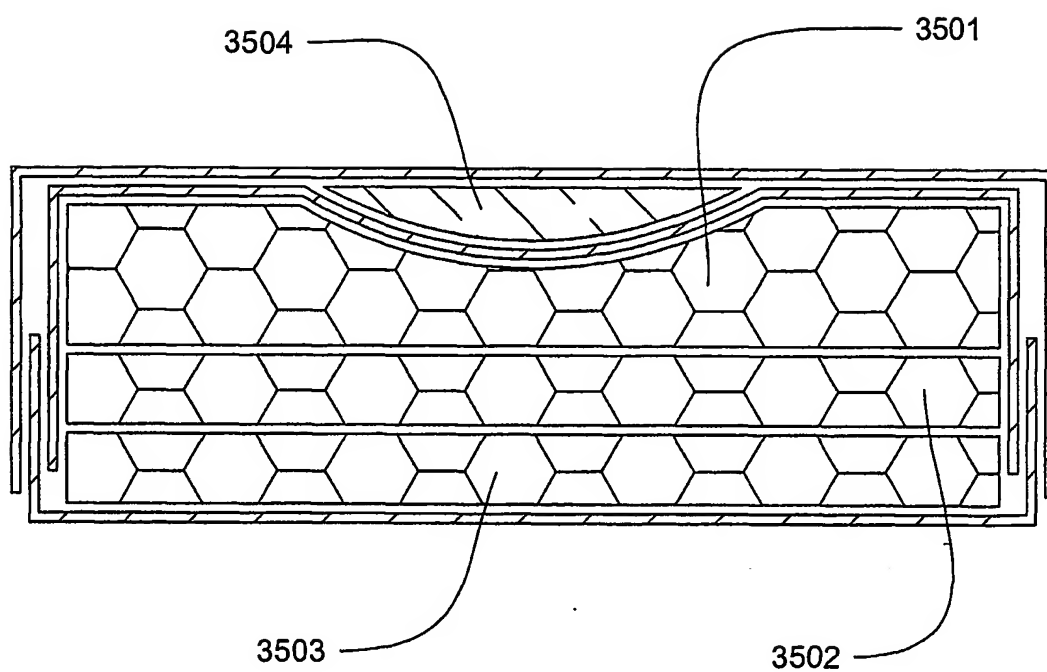


Fig. 35

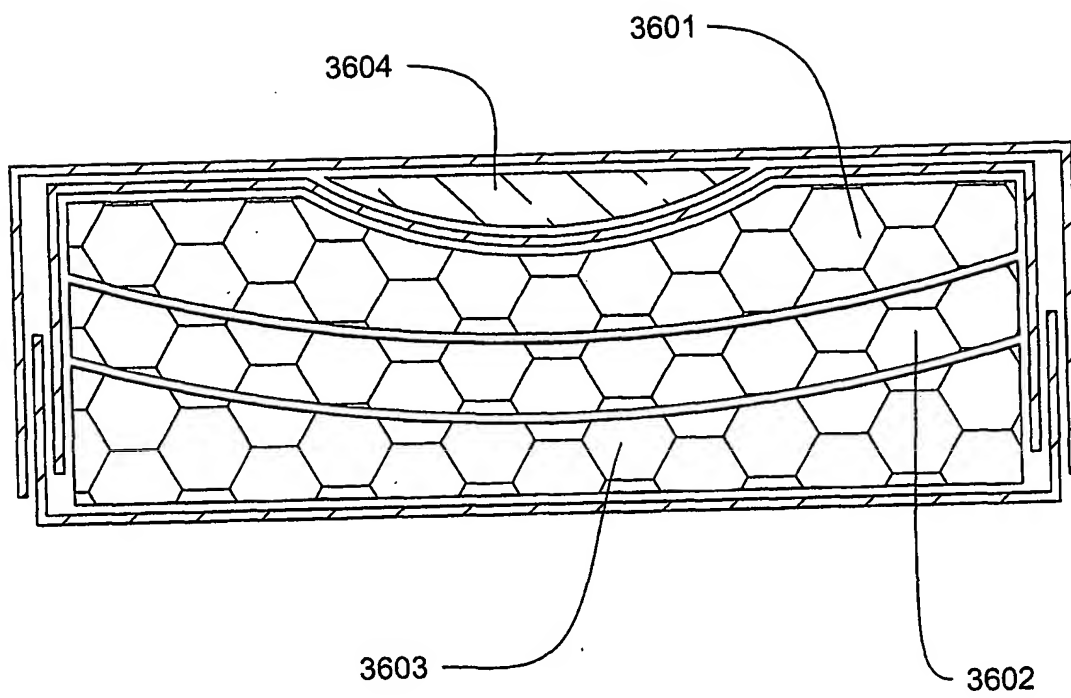


Fig. 36

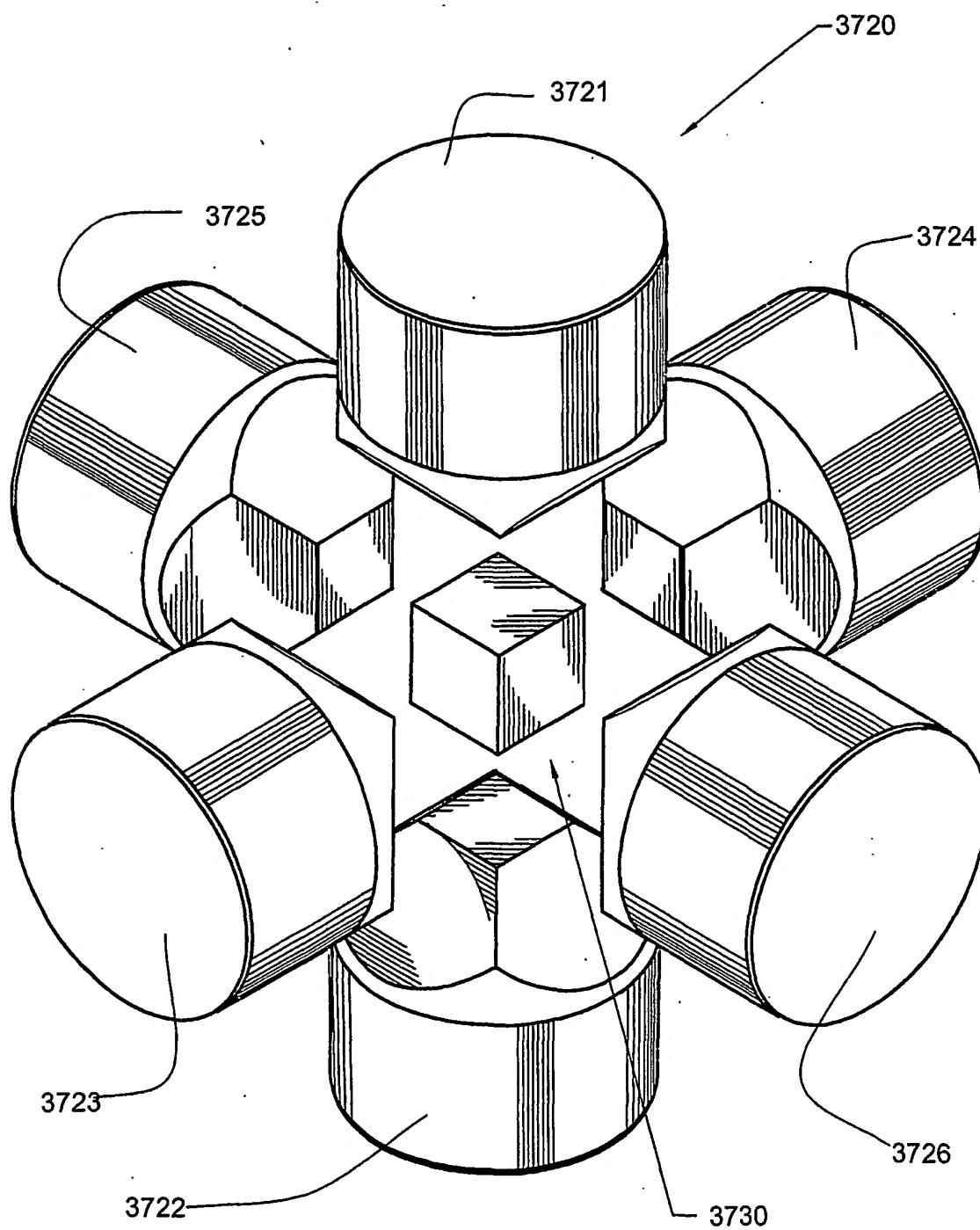
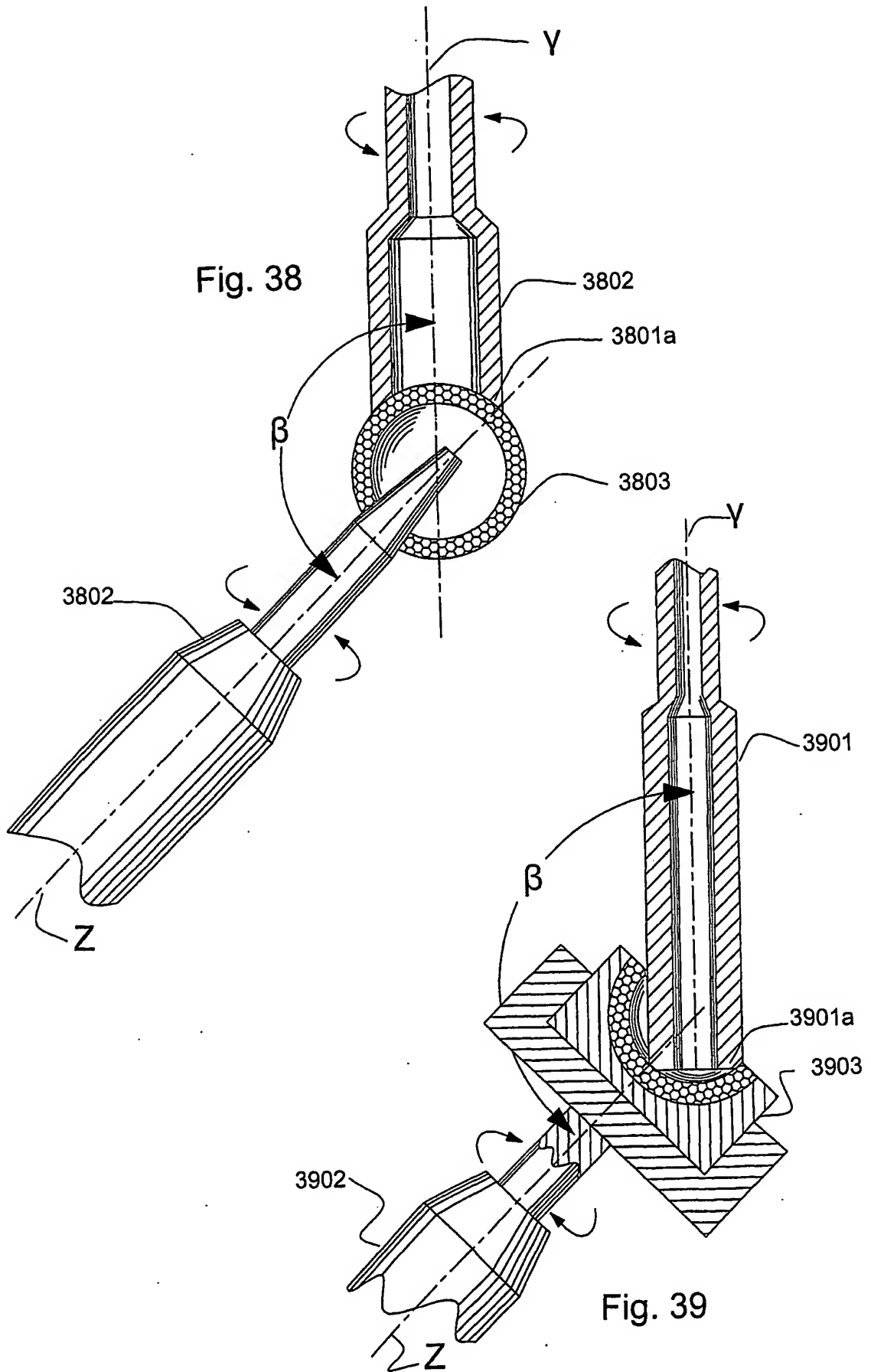


Fig. 37

45/97



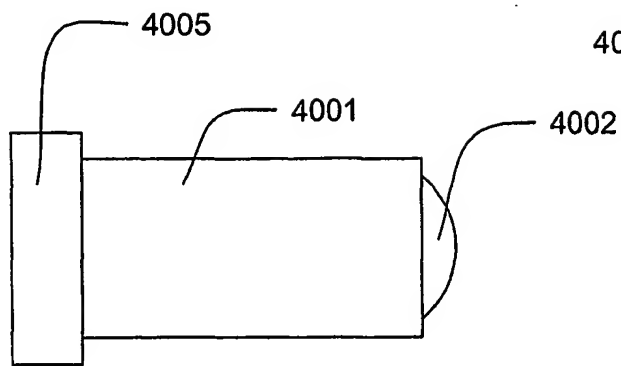


Fig. 40

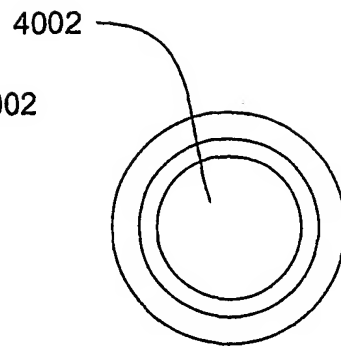


Fig. 40a

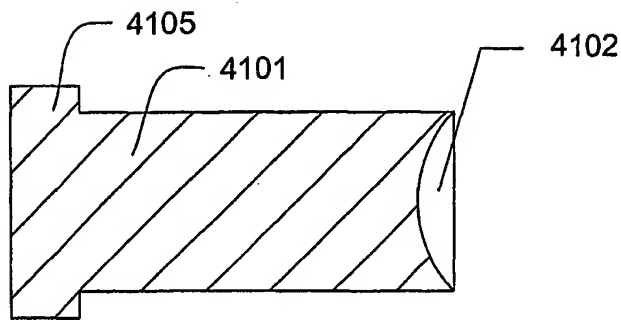


Fig. 41

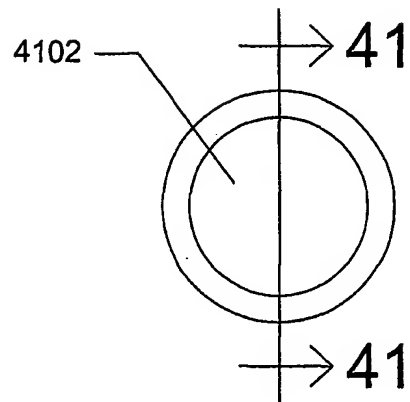


Fig. 41a

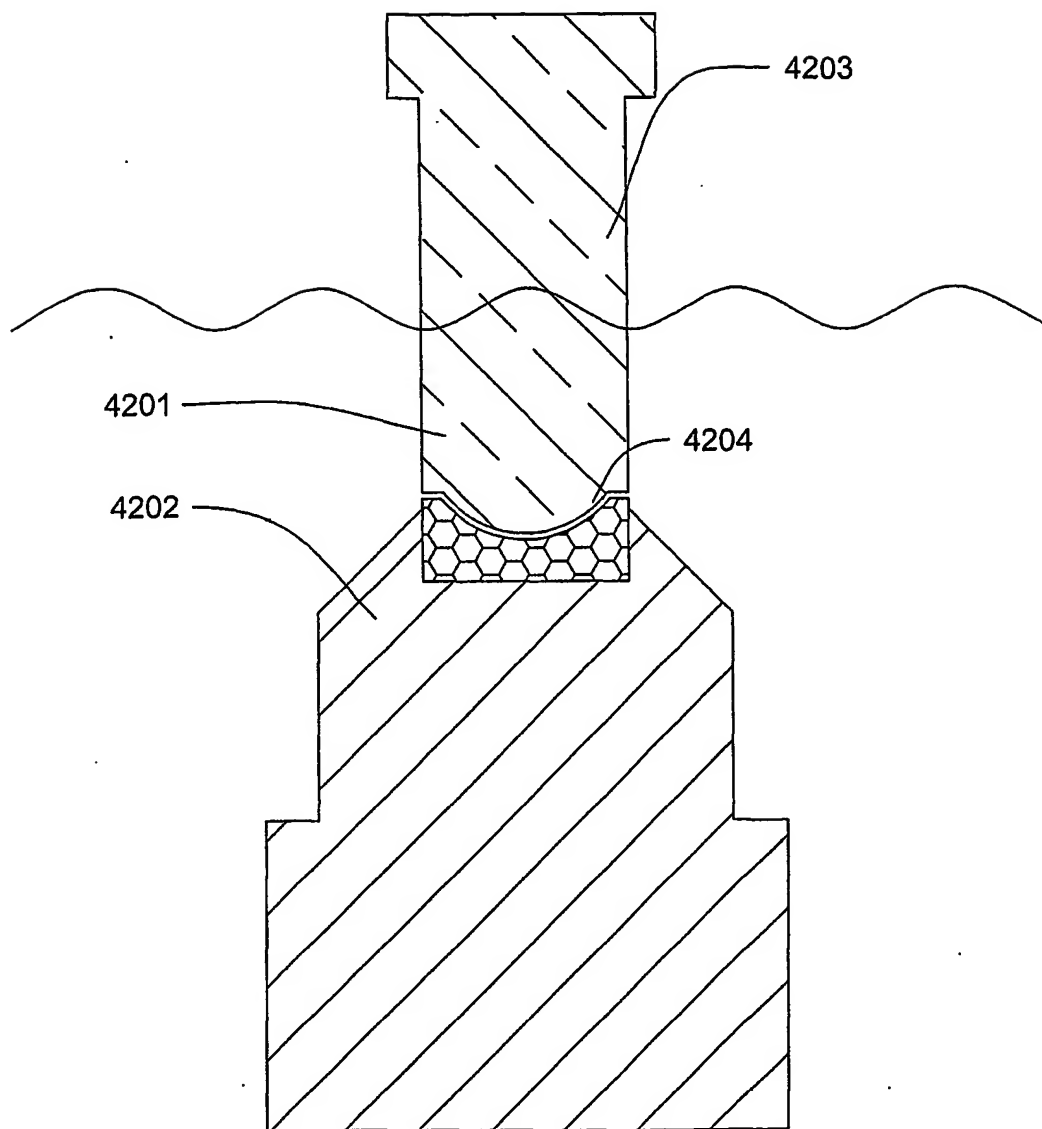


Fig. 42



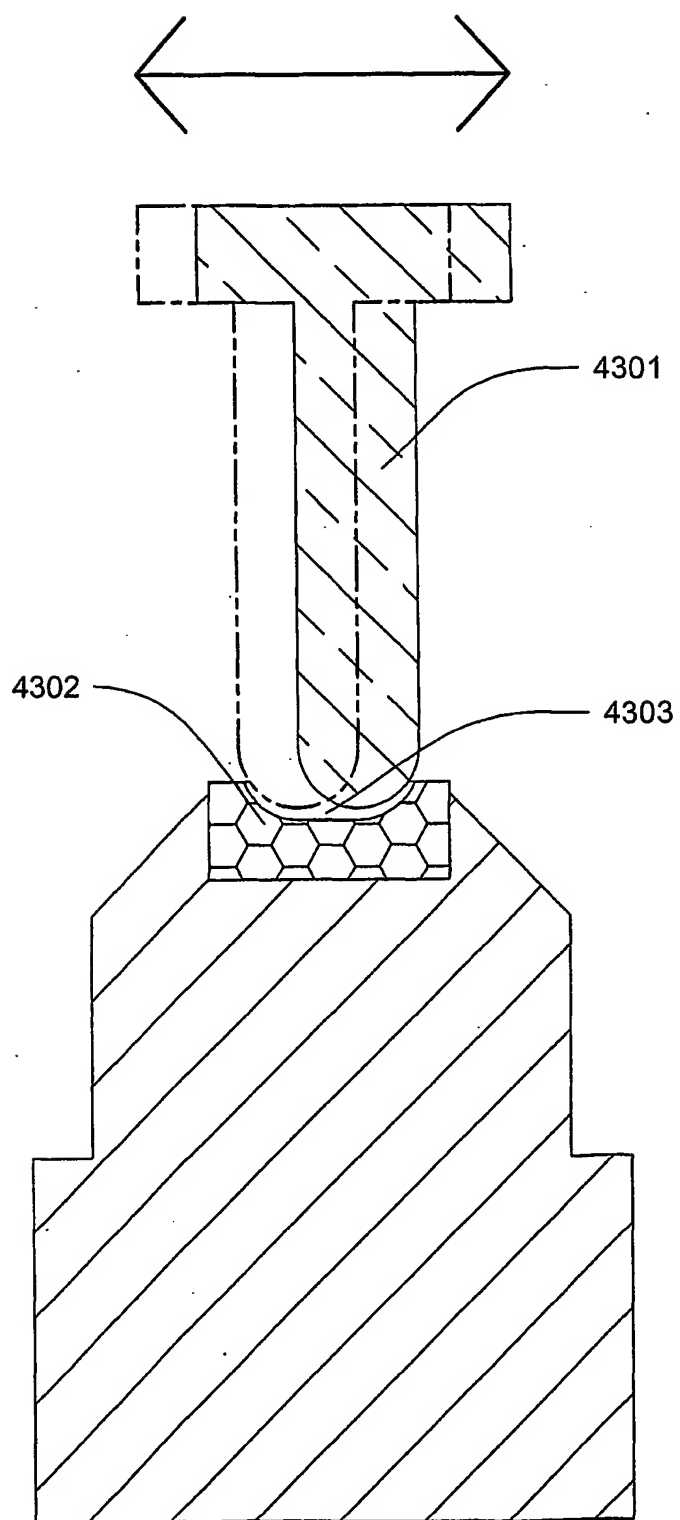


Fig. 43

Fig. 44

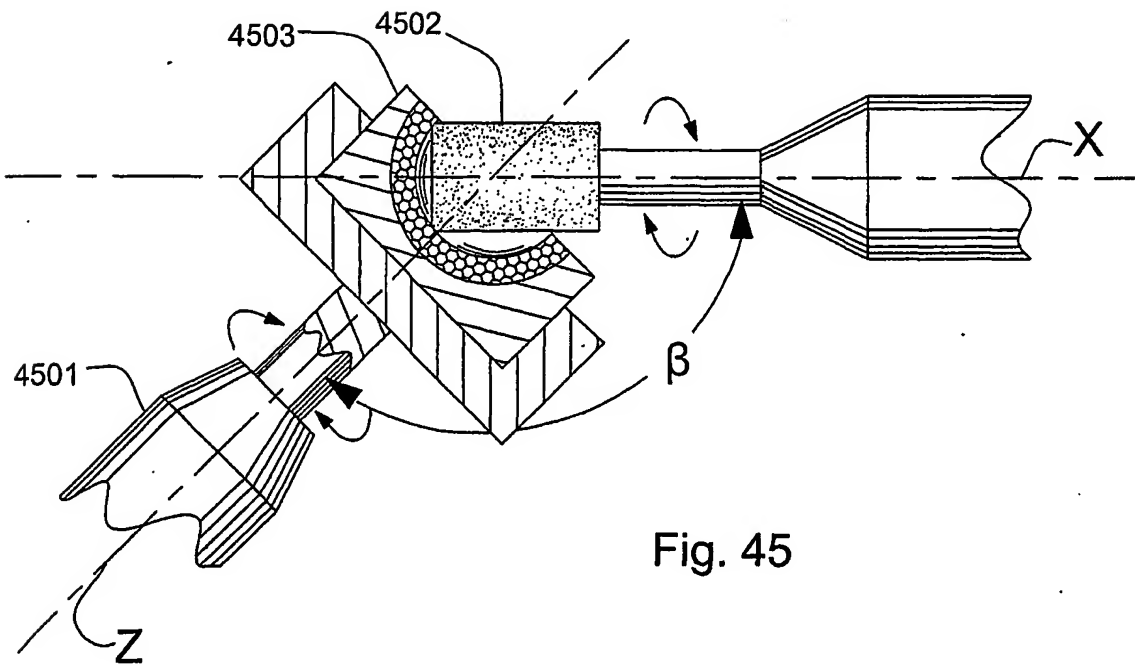
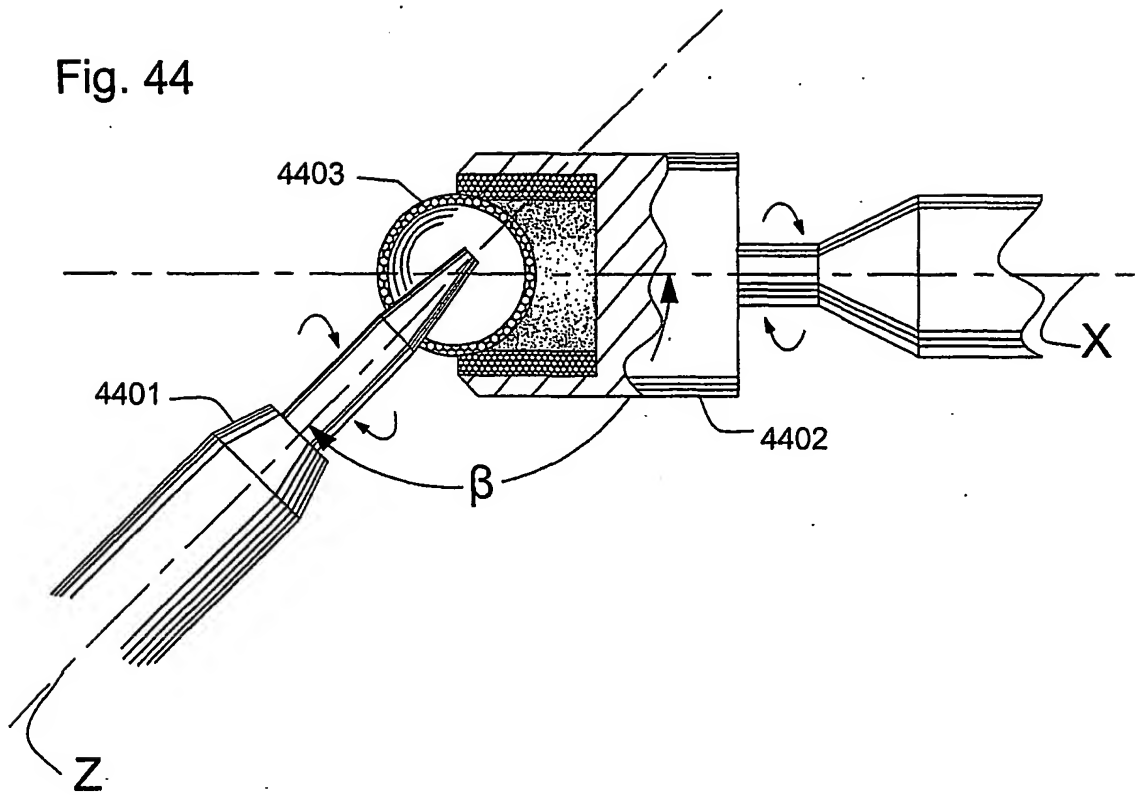


Fig. 45

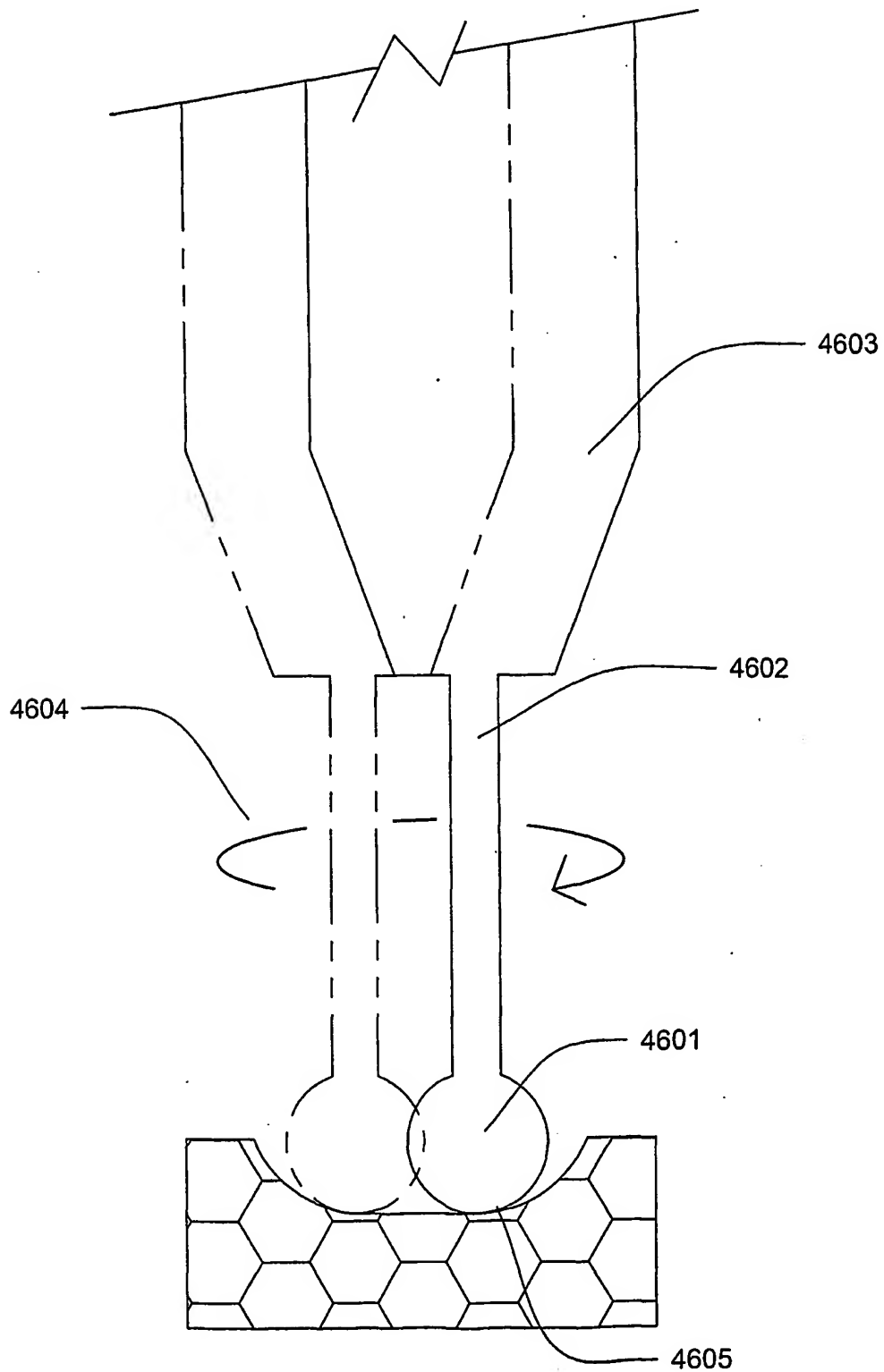


Fig. 46

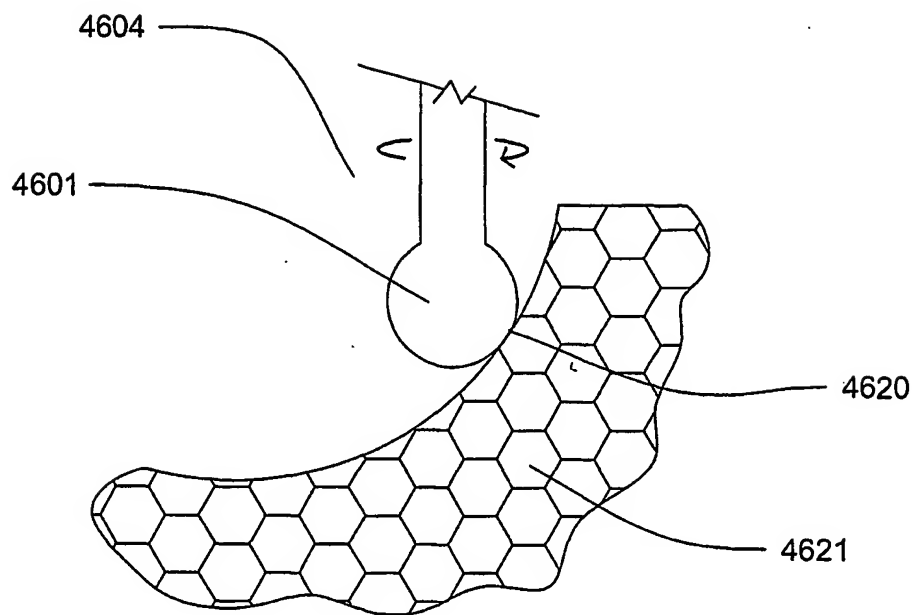


Fig. 47

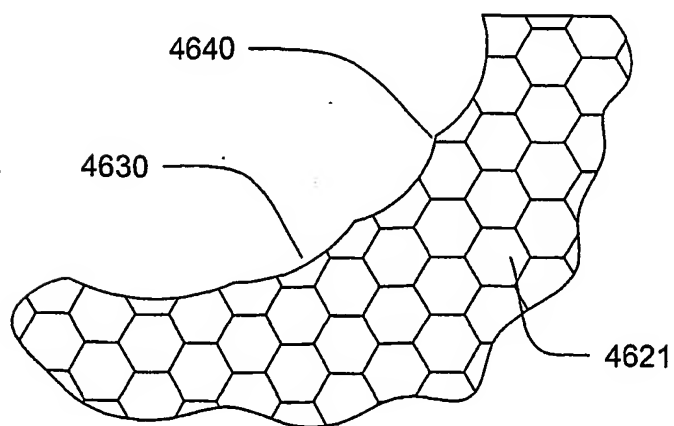


Fig. 48

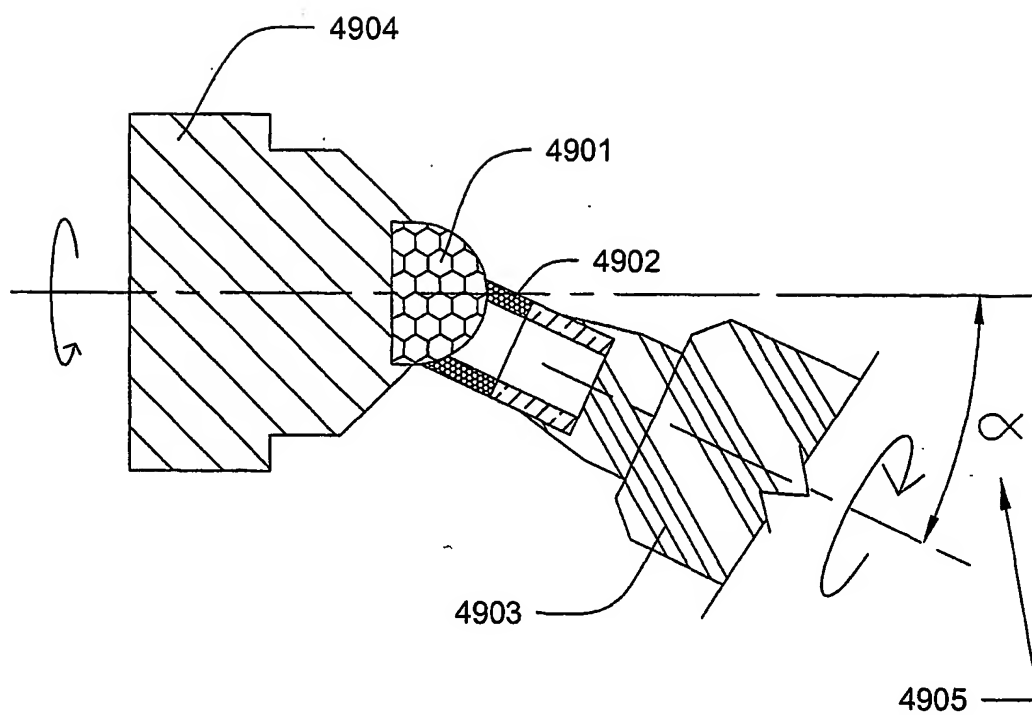


Fig. 49

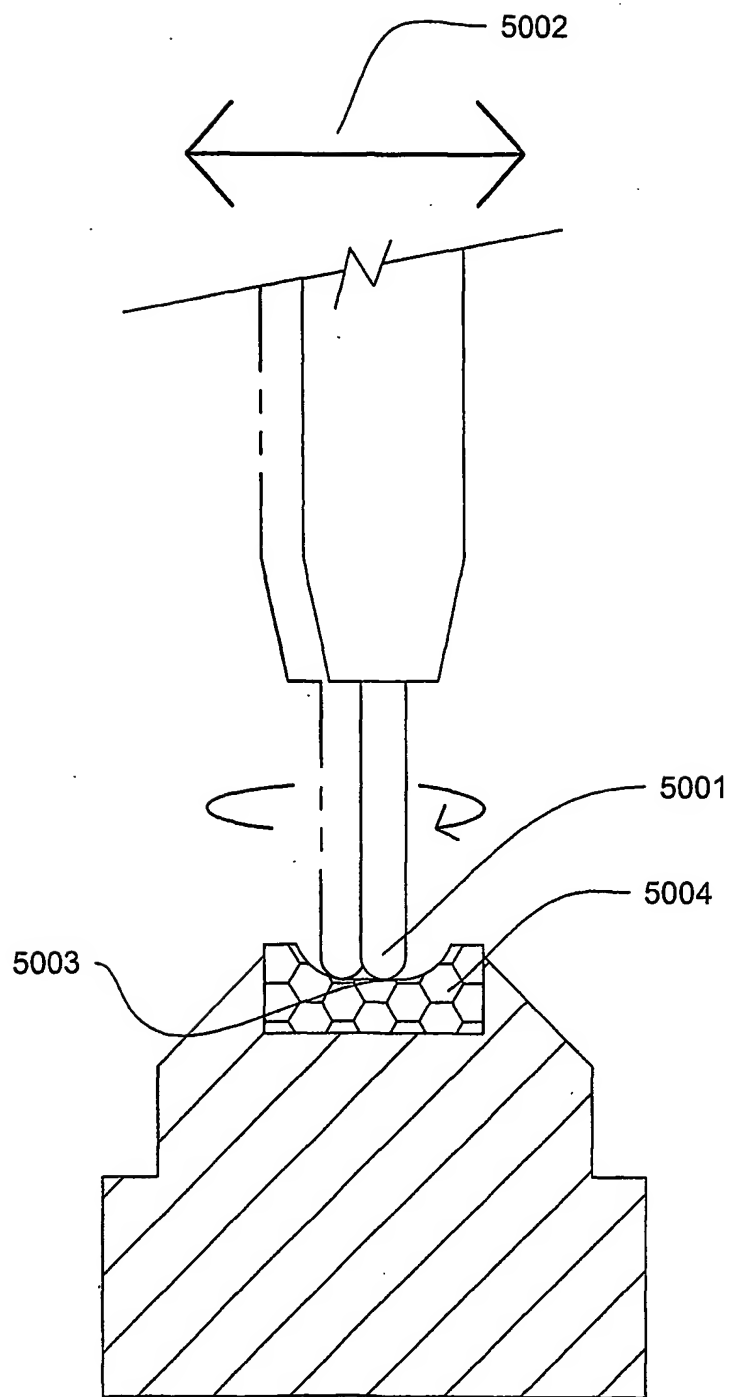
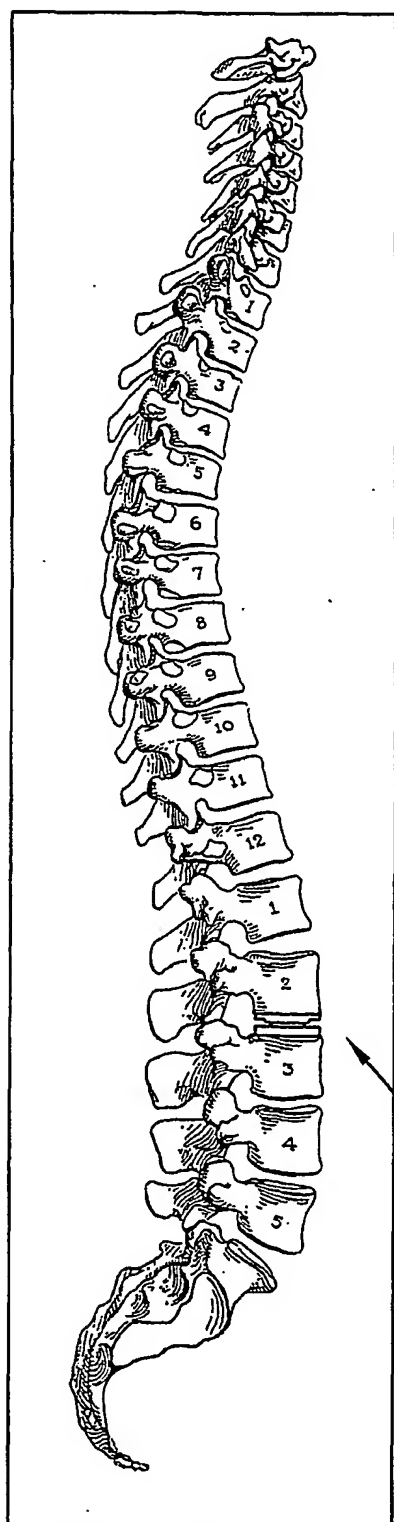
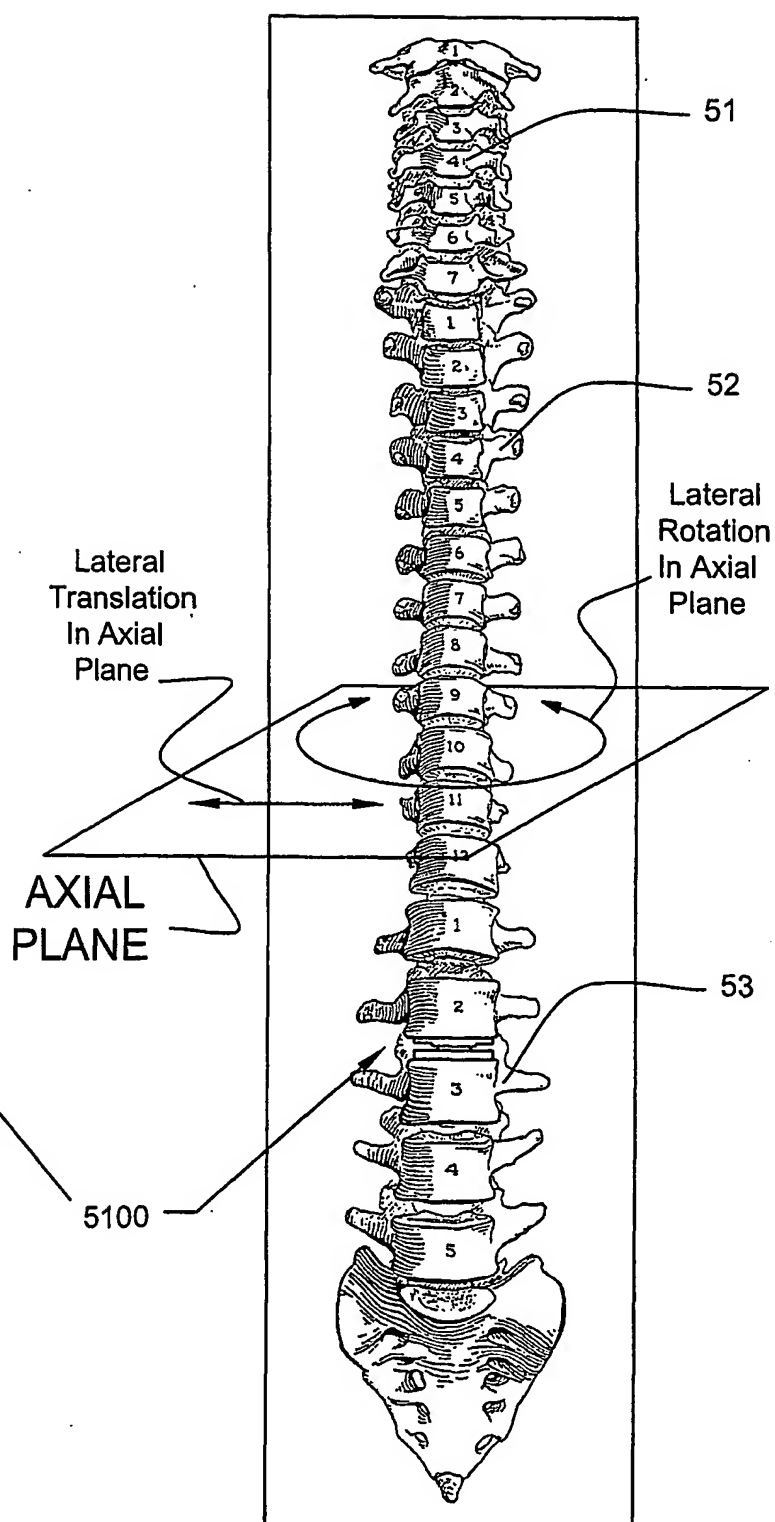


Fig. 50



SAGITTAL PLANE

FIG. 51



CORONAL PLANE

FIG. 52

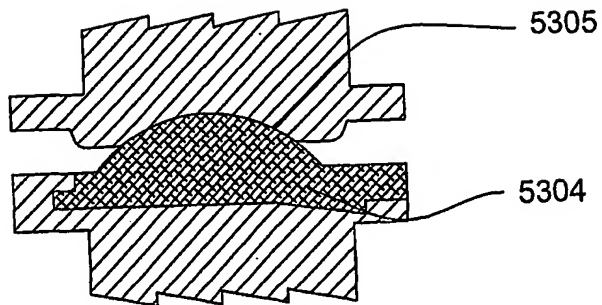


FIG. 53-4

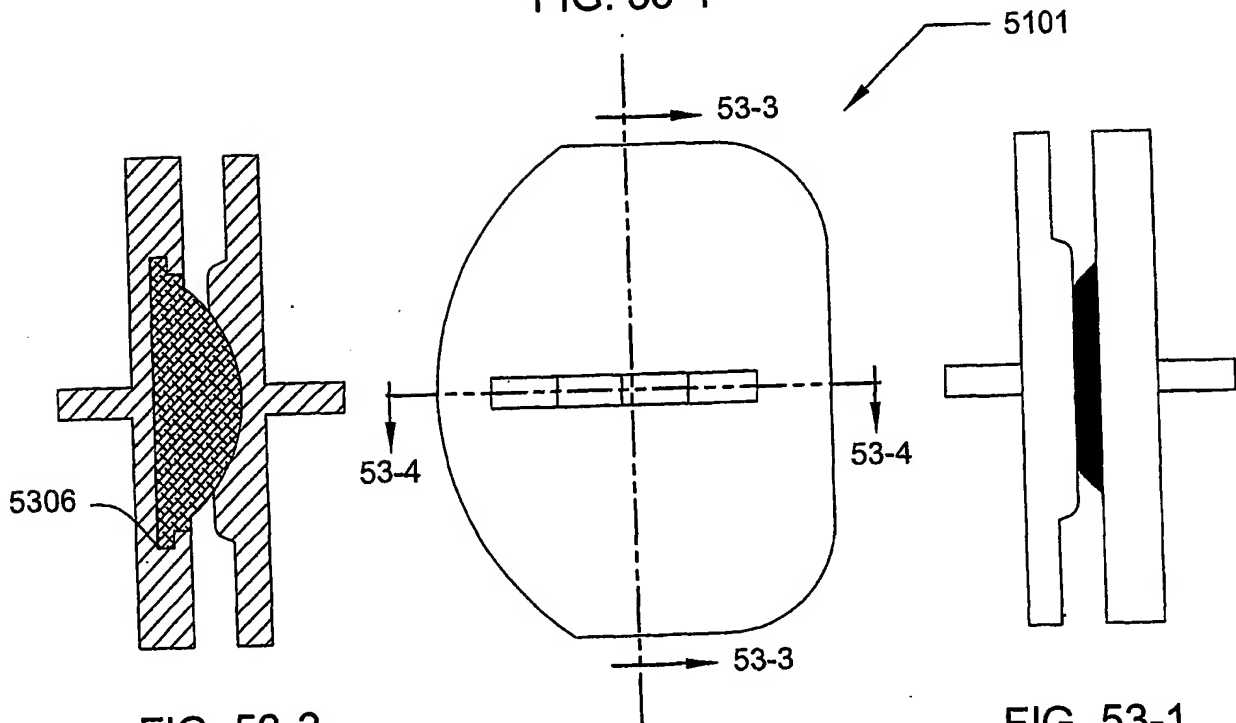


FIG. 53-3

FIG. 53

FIG. 53-1

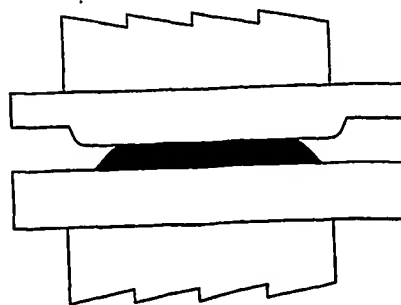


FIG. 53-2



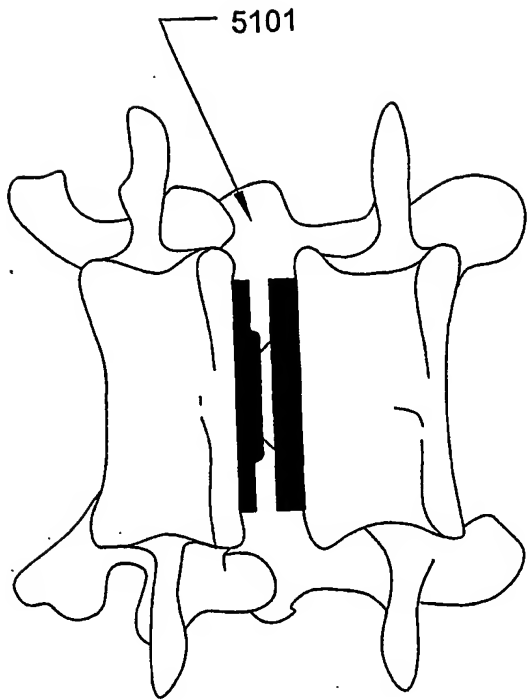


FIG. 54

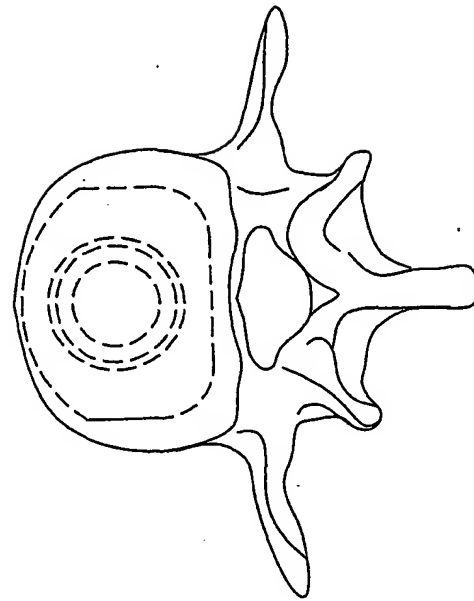


FIG. 55

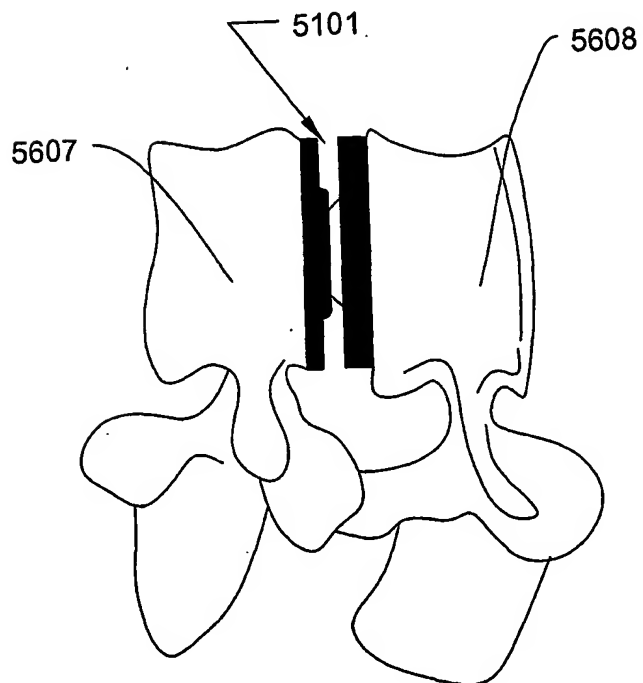


FIG. 56

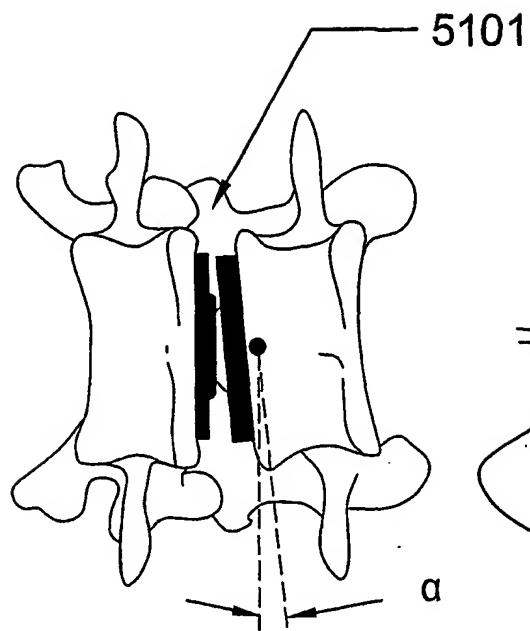


FIG. 57

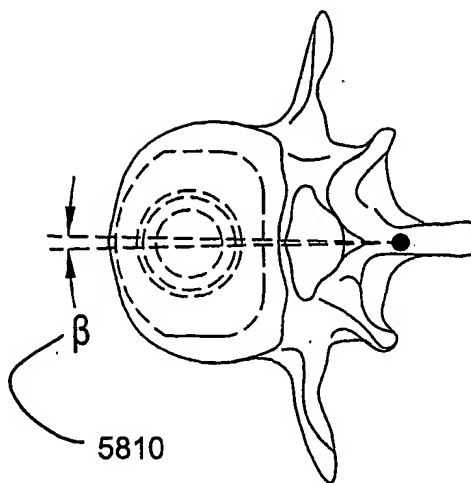


FIG. 58

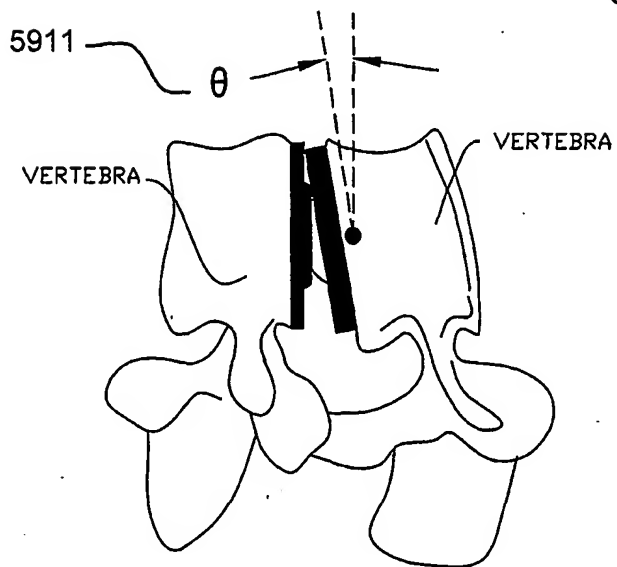


FIG. 59

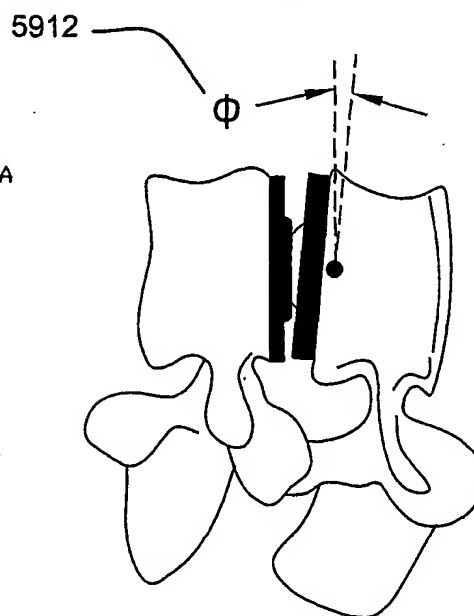


FIG. 60

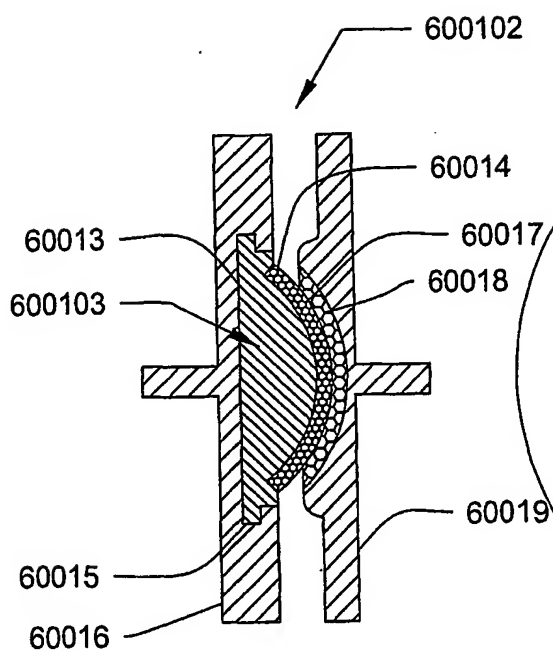


FIG. 61-1

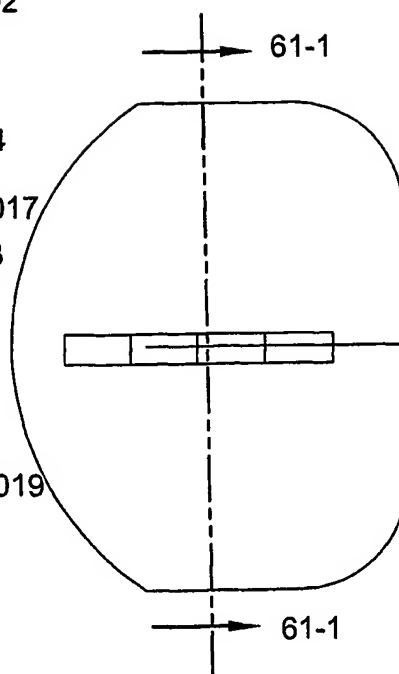


FIG. 61

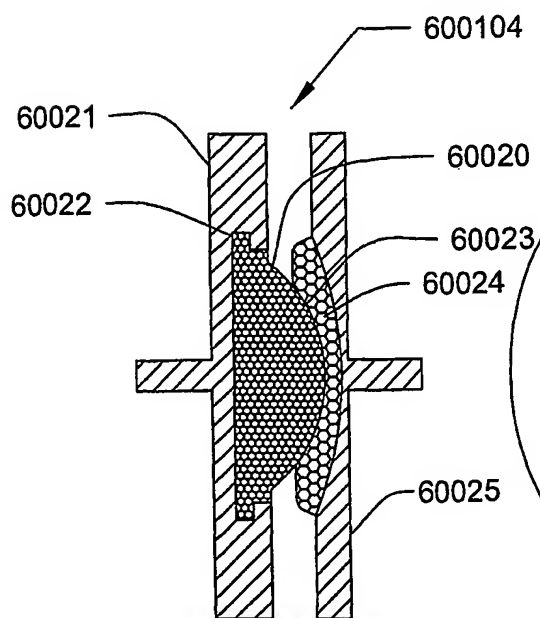


FIG. 62-1

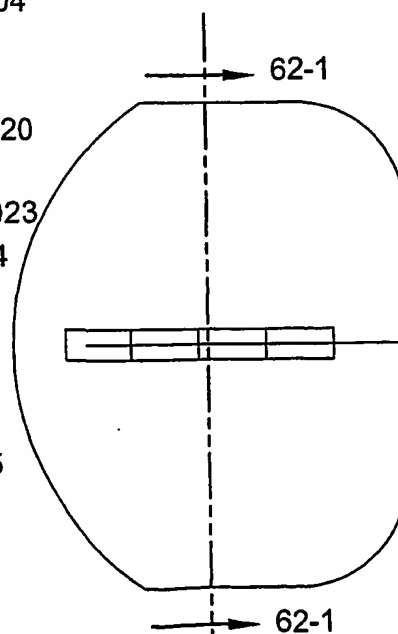


FIG. 62

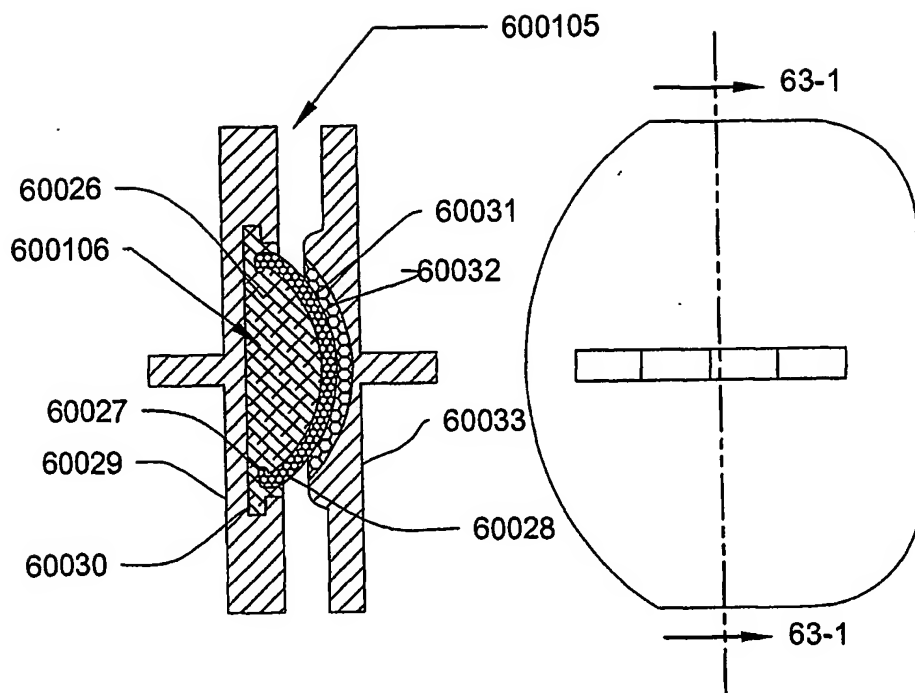


FIG. 63-1

FIG. 63

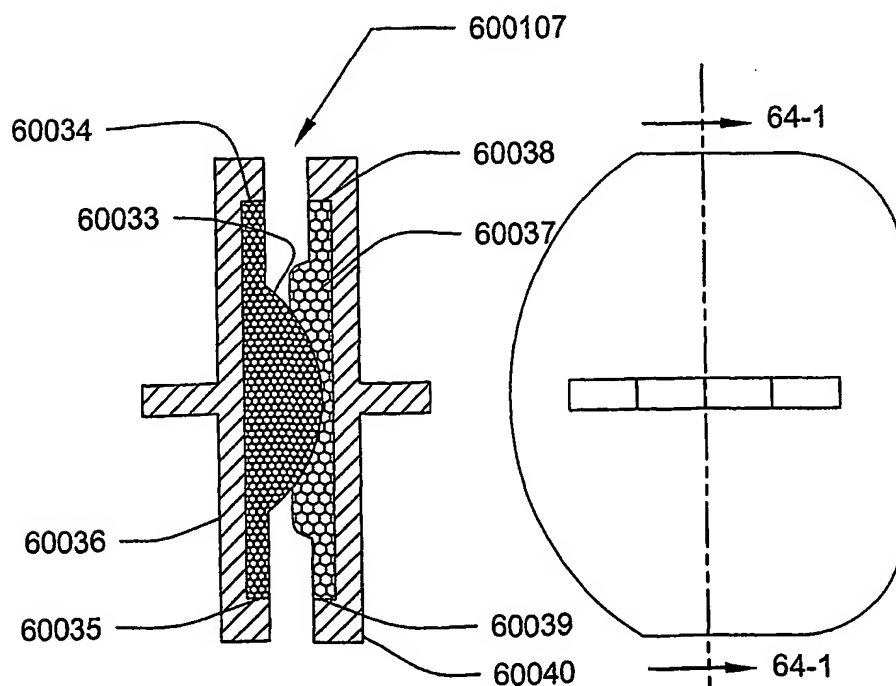
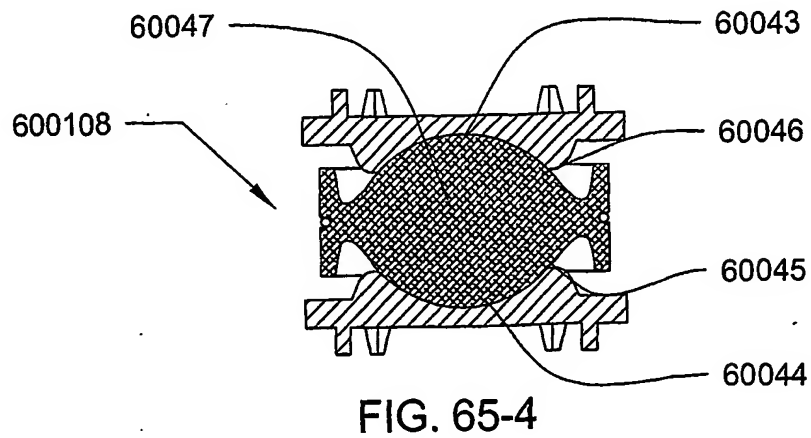
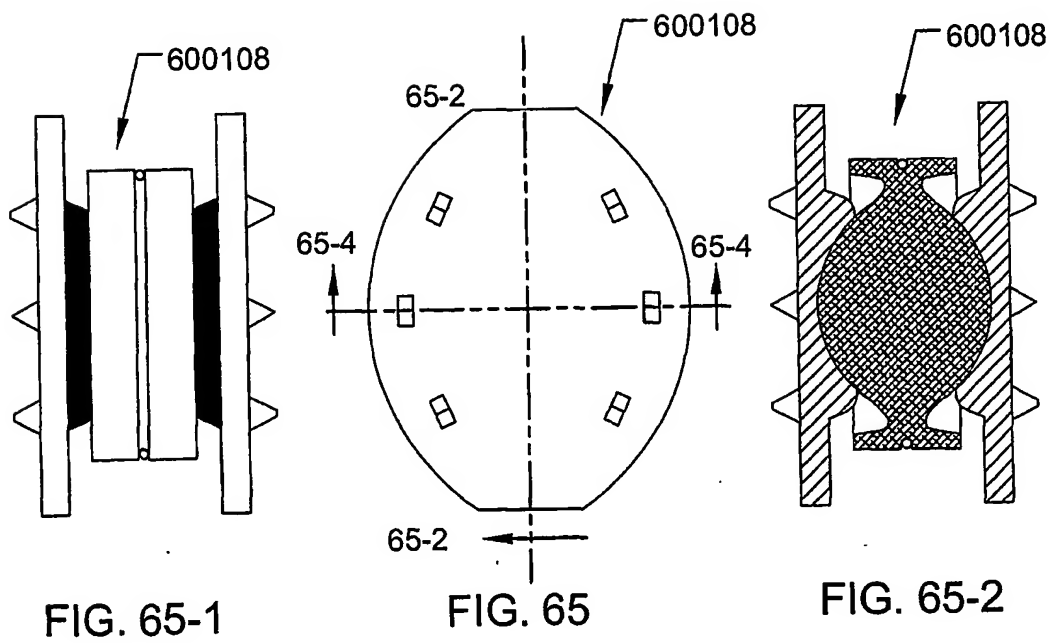
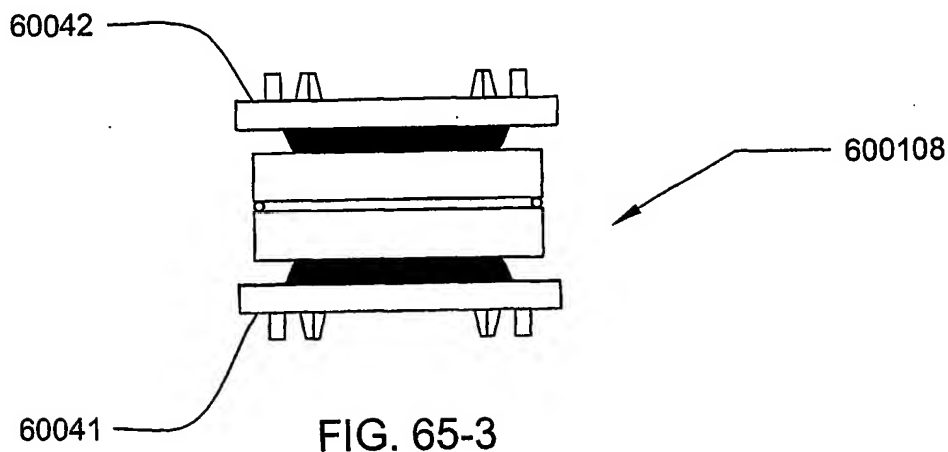


FIG. 64-1

FIG. 64



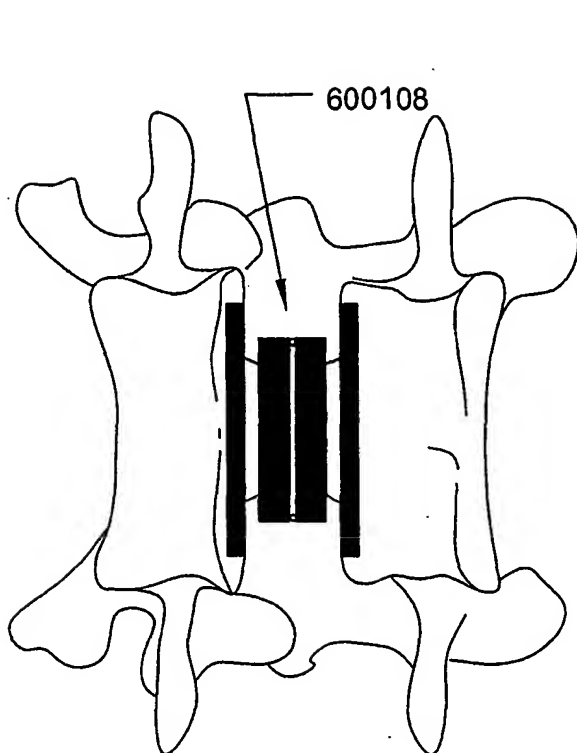


FIG. 66

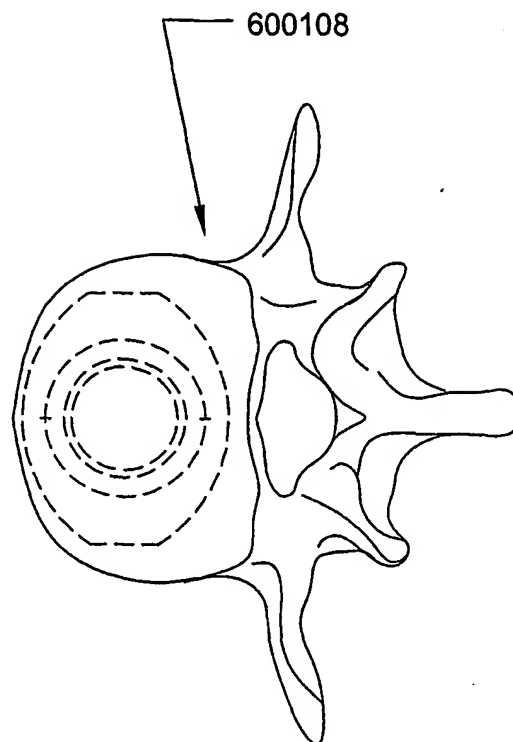


FIG. 67

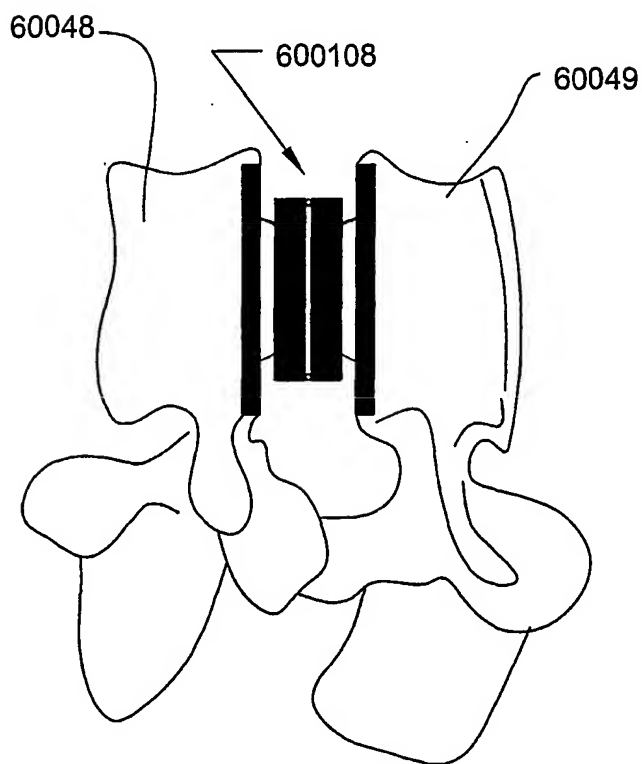


FIG. 68

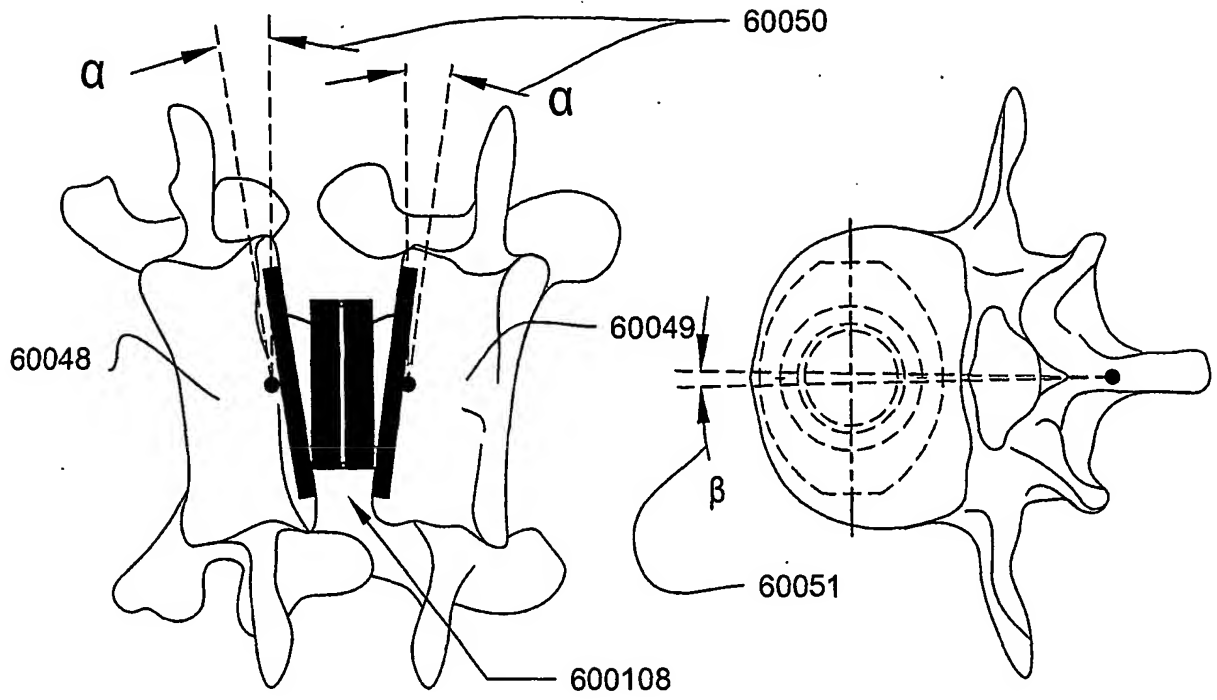


FIG. 69

FIG. 70

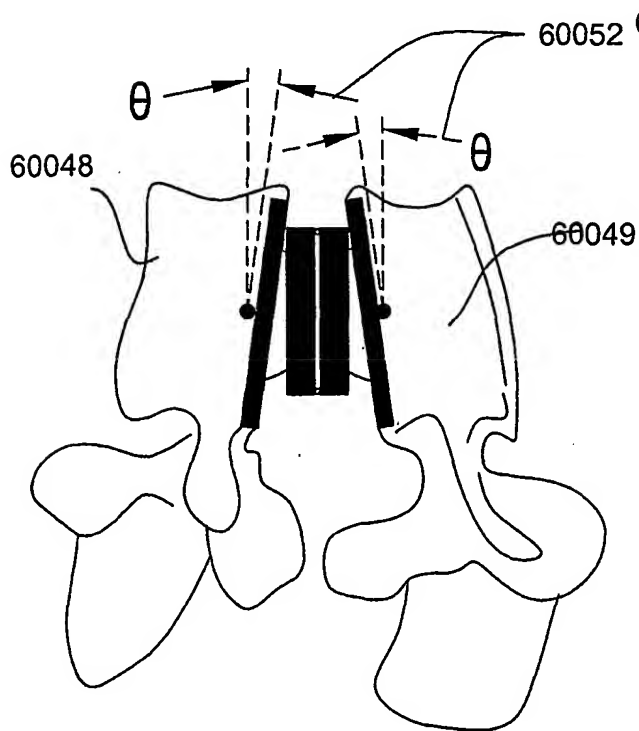


FIG. 71

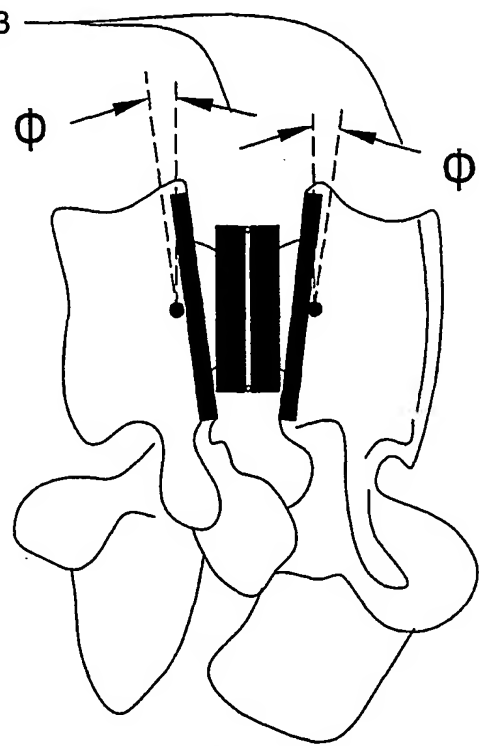


FIG. 72

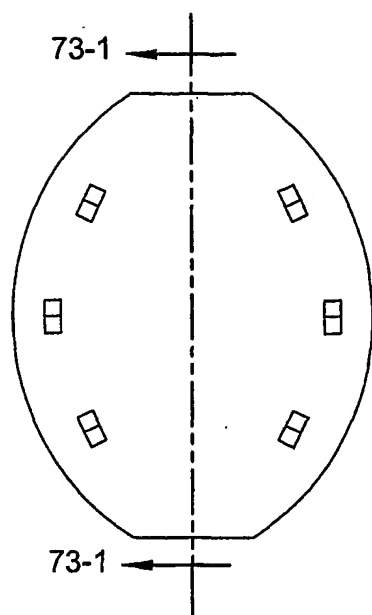


FIG. 73

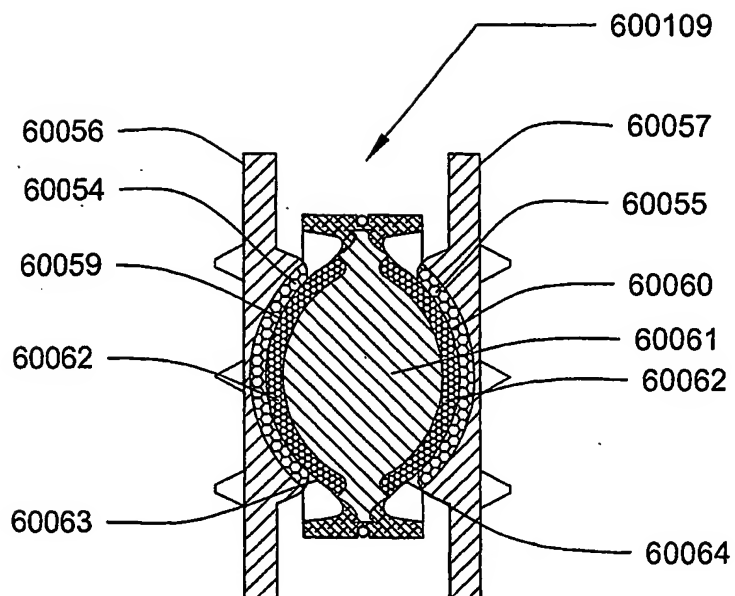


FIG. 73-1

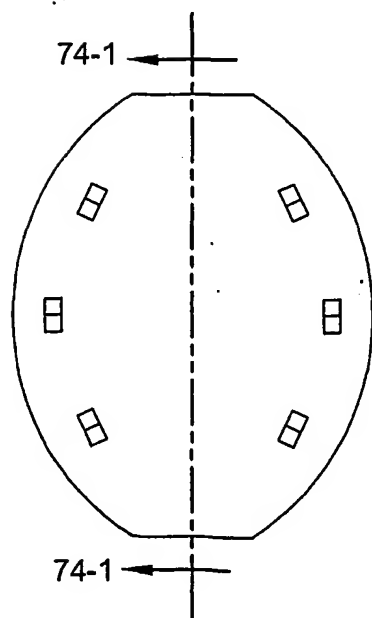


FIG. 74

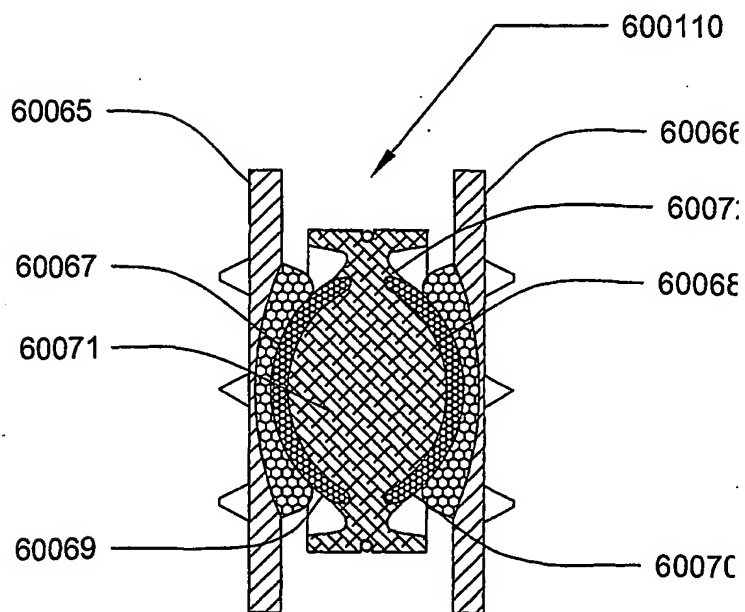


FIG. 74-1



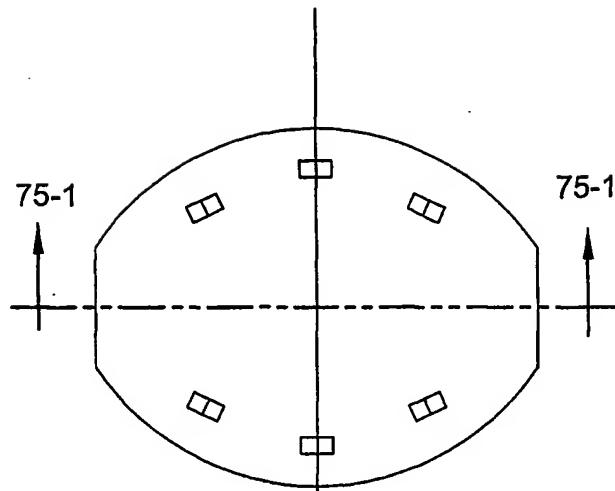


FIG. 75

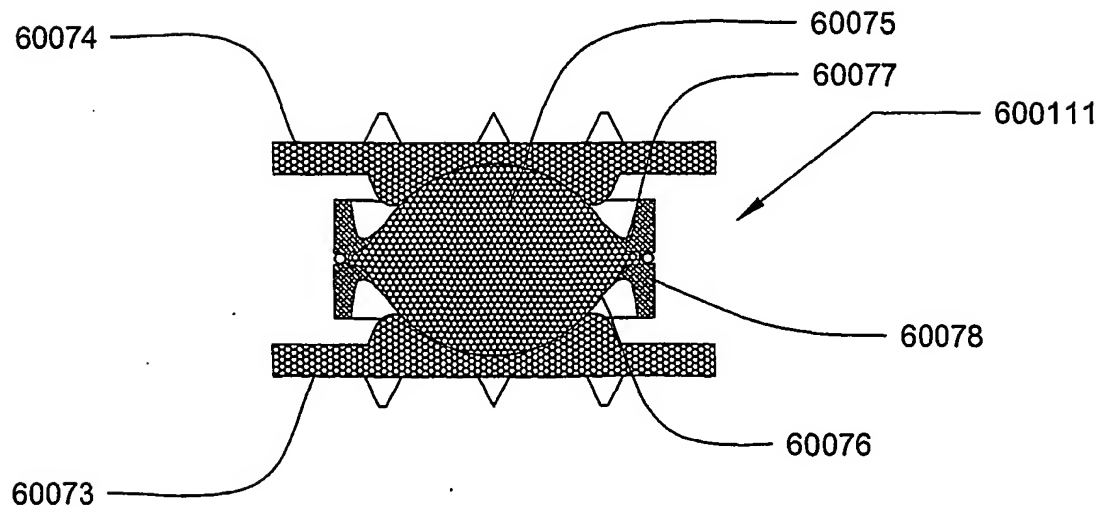


FIG. 75-1

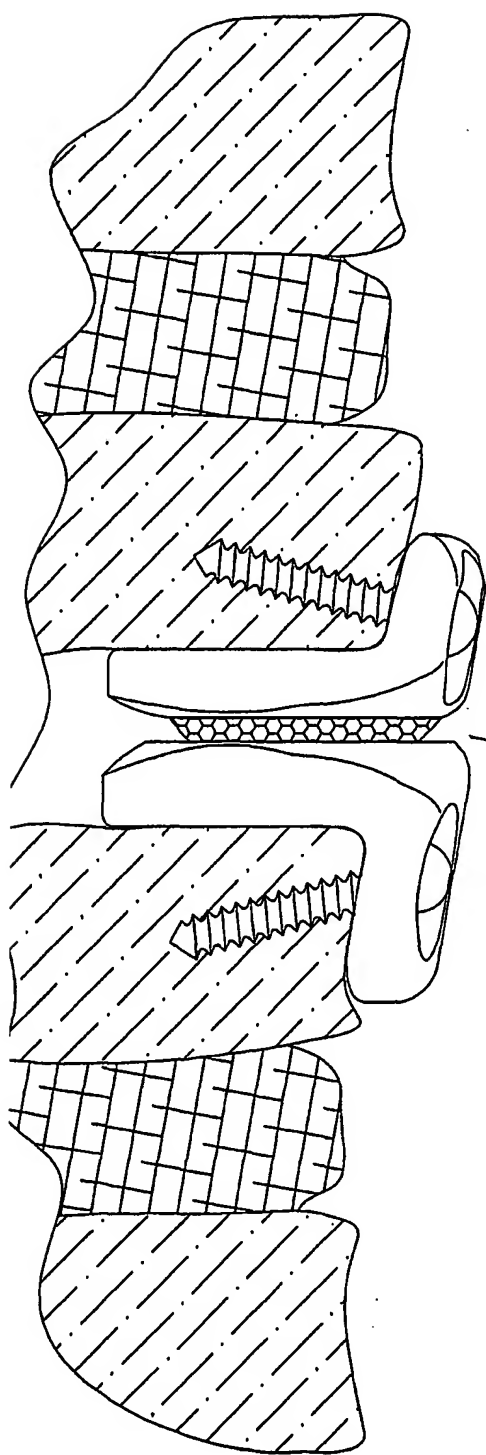


Fig. 76

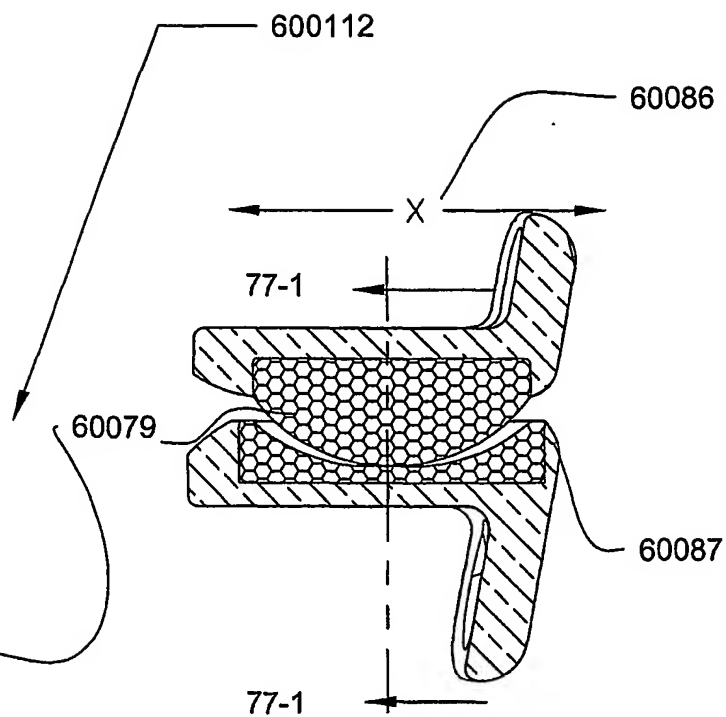


Fig. 77

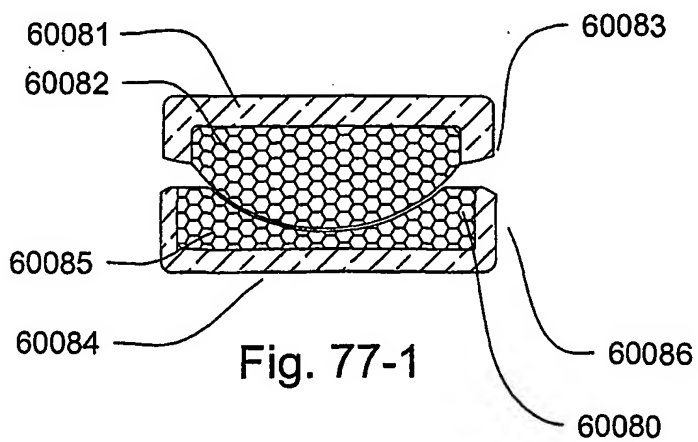


Fig. 77-1

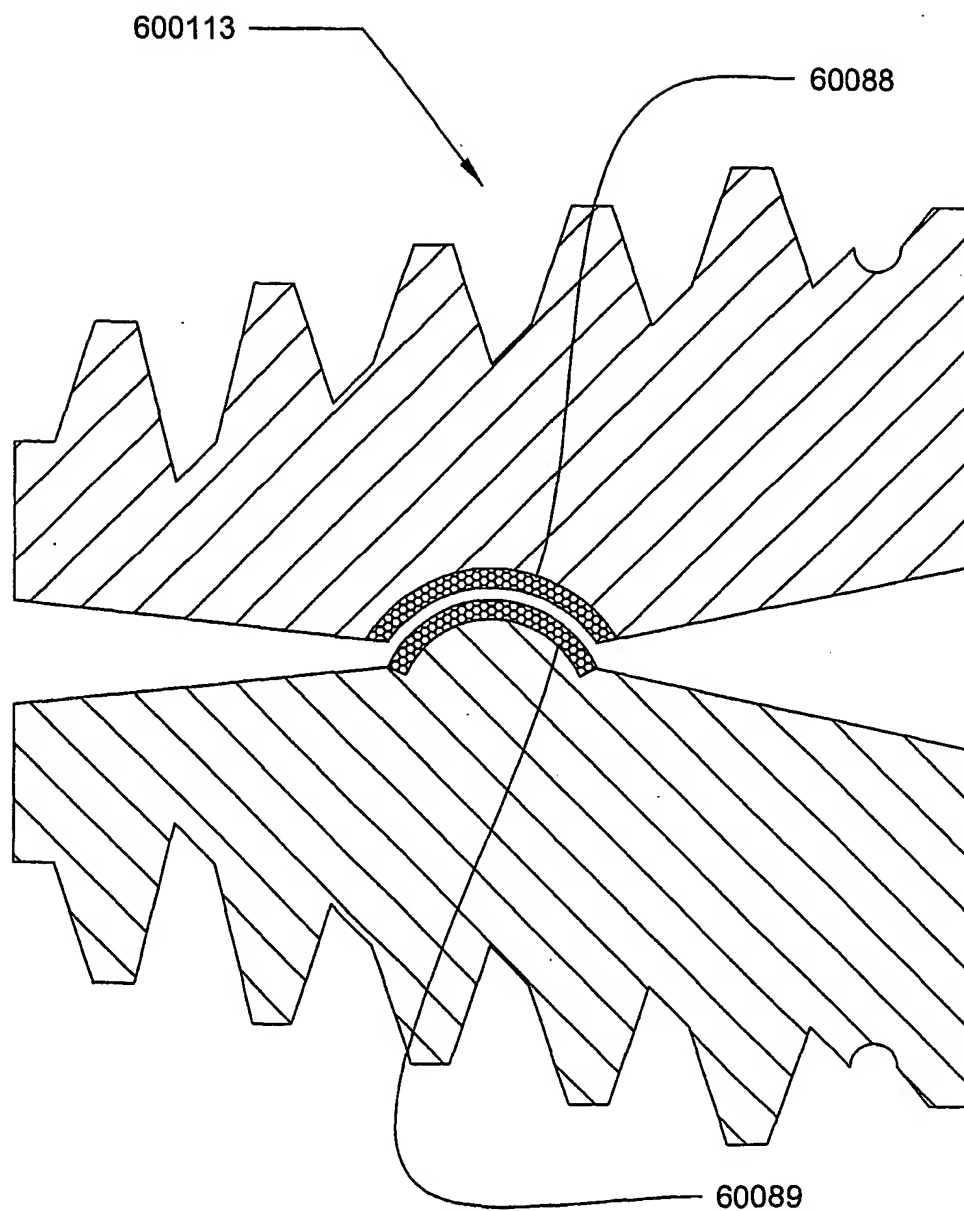


FIG. 79

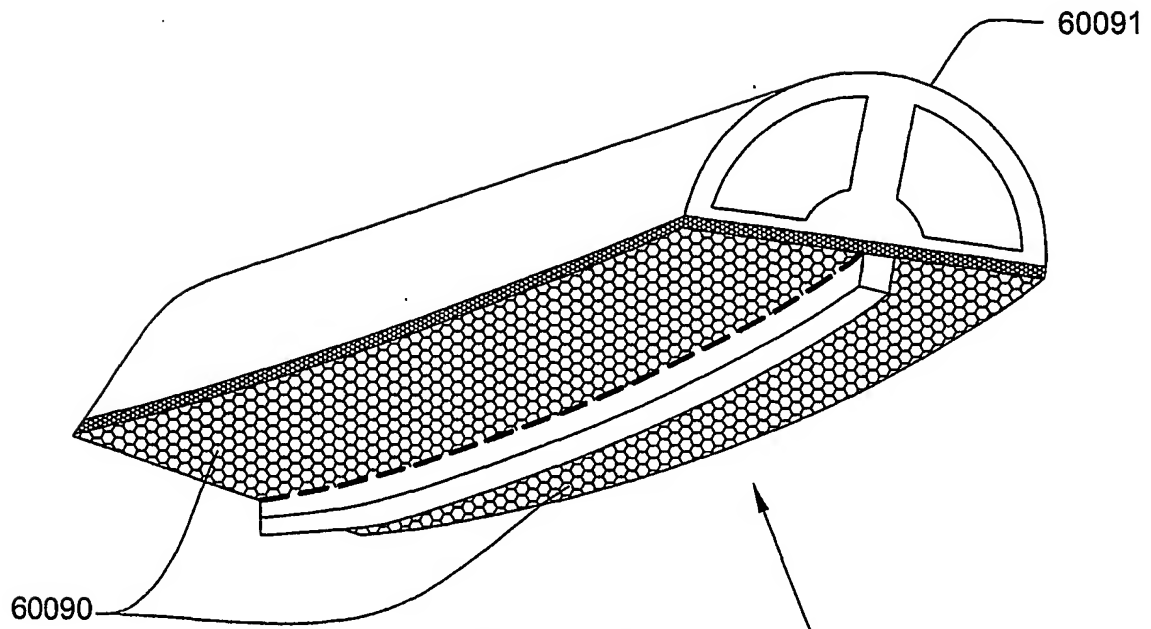


FIG. 80A

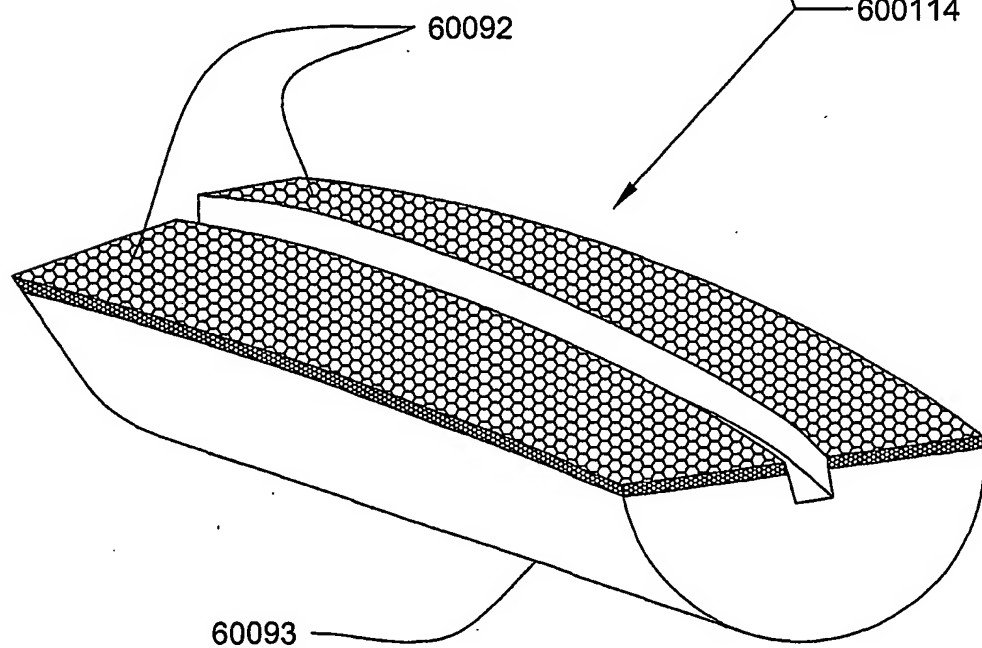


FIG. 80B

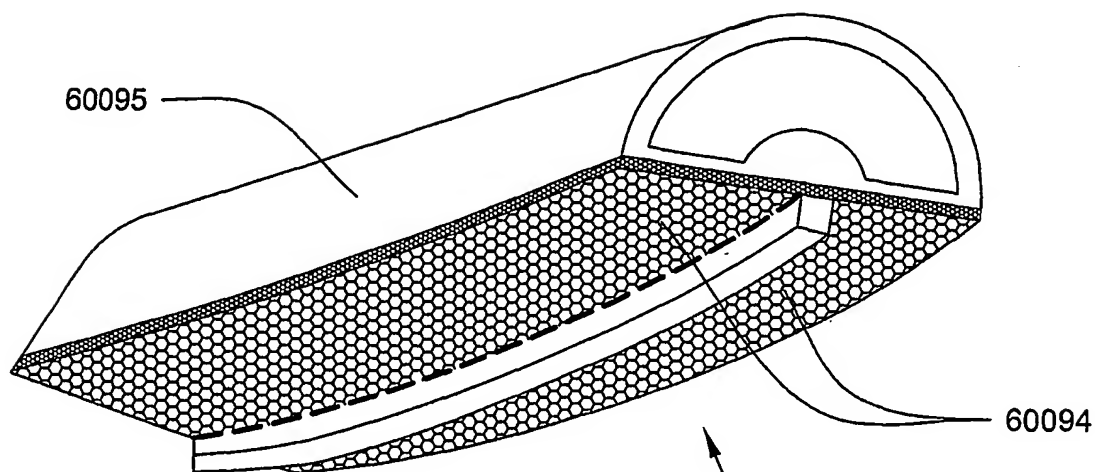


FIG. 81A

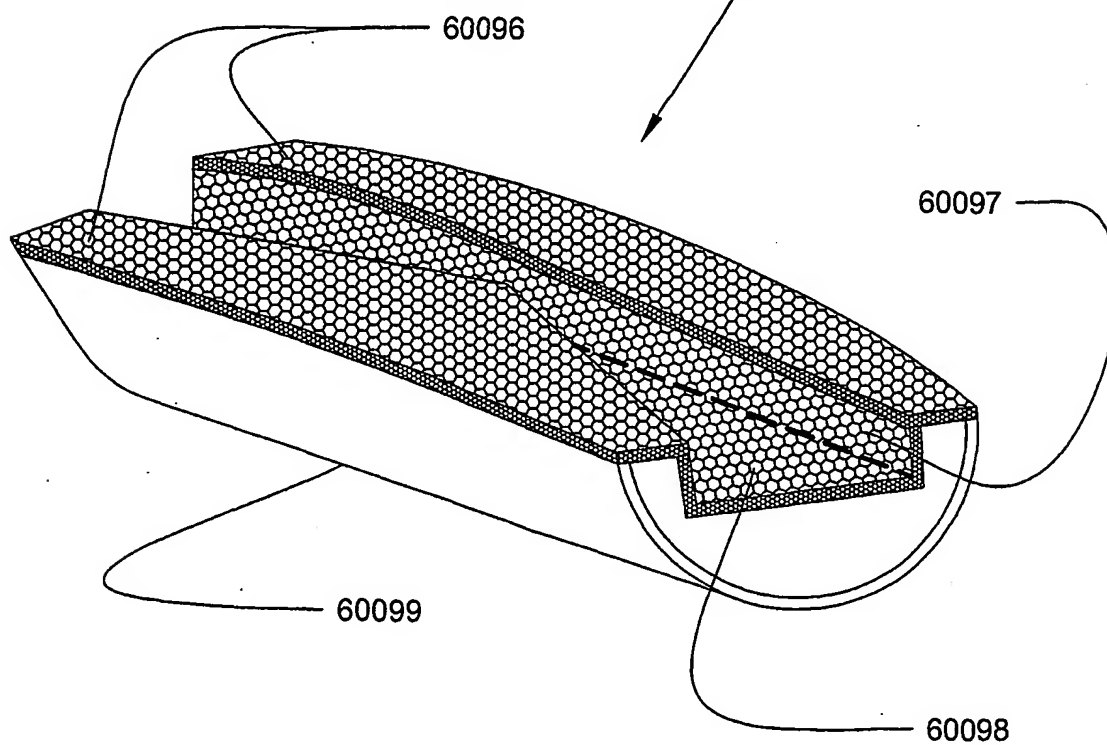
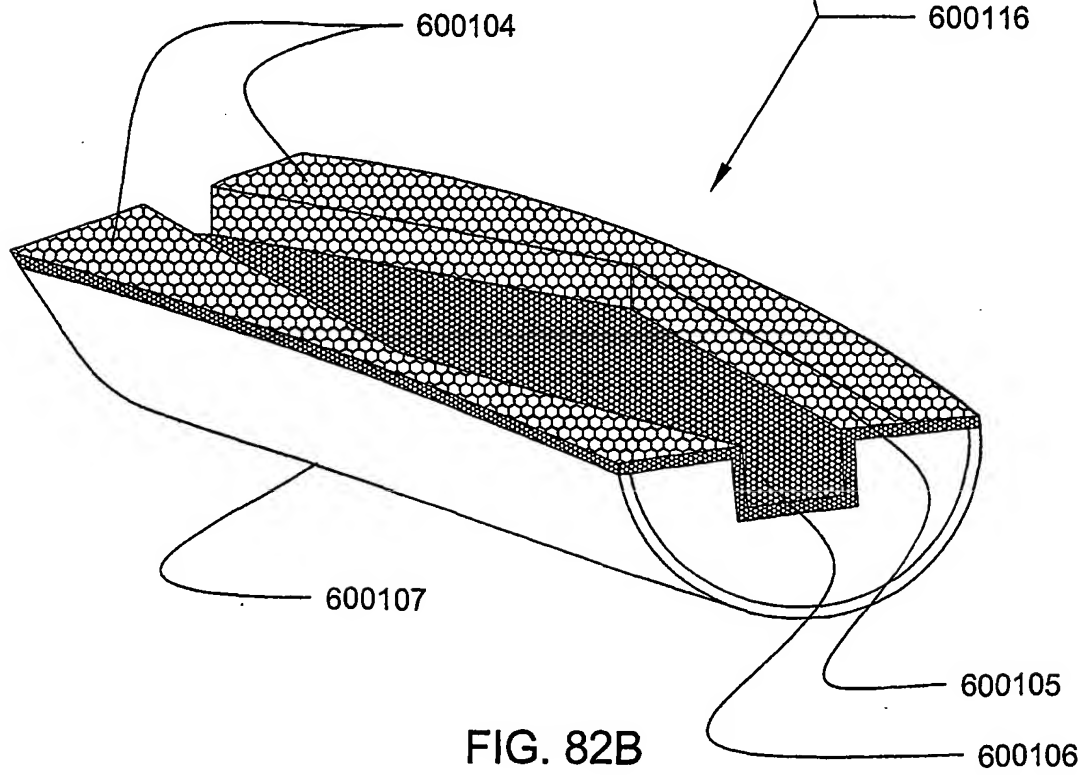
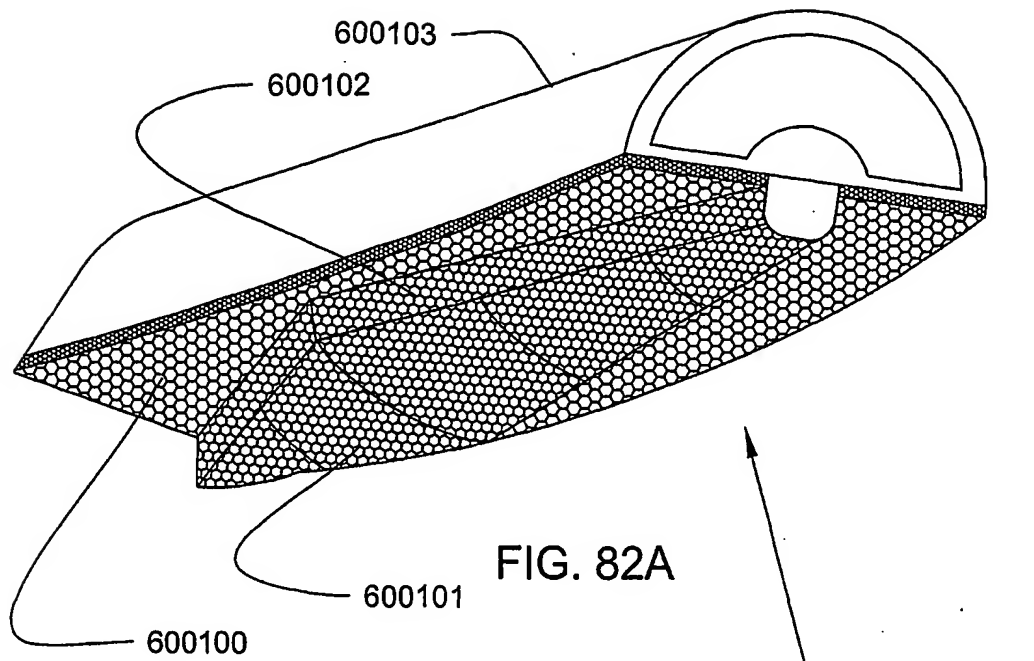
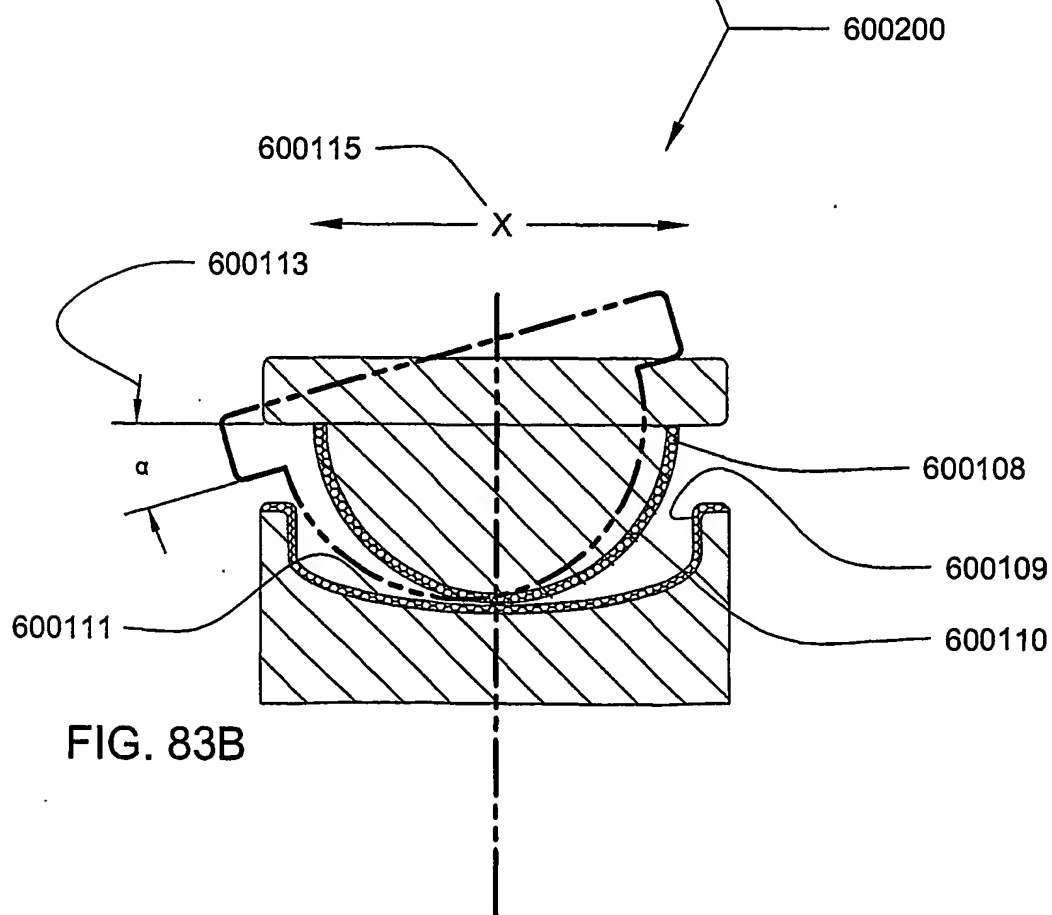
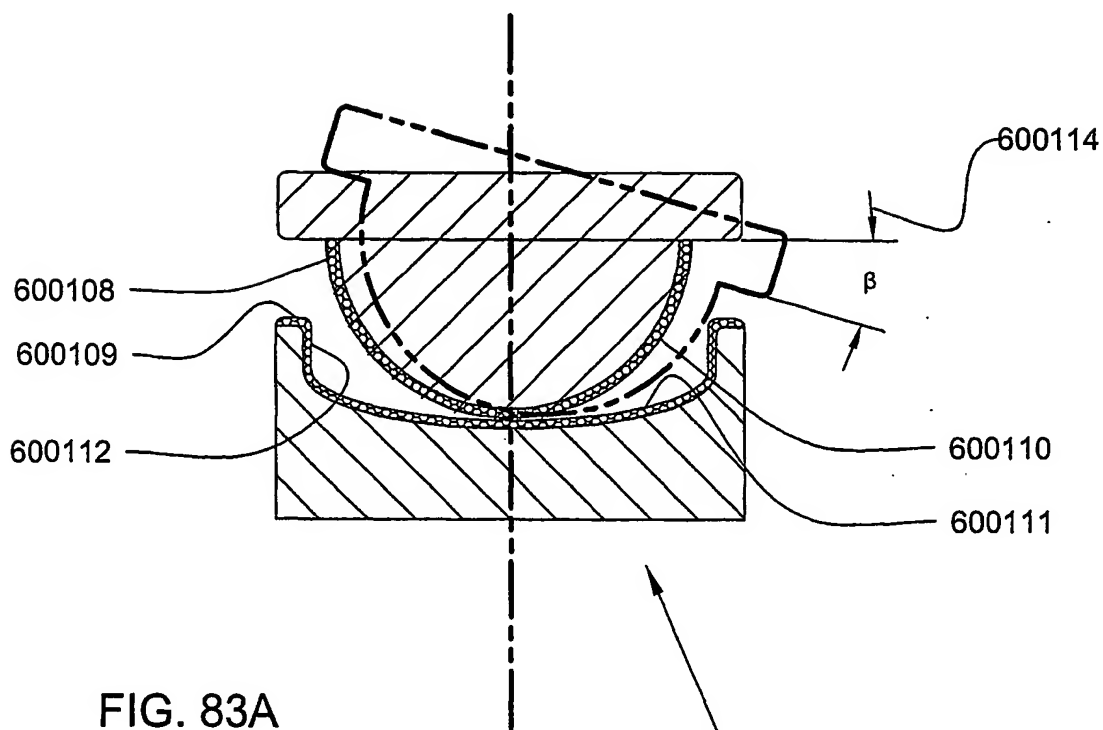


FIG. 81B



70/97



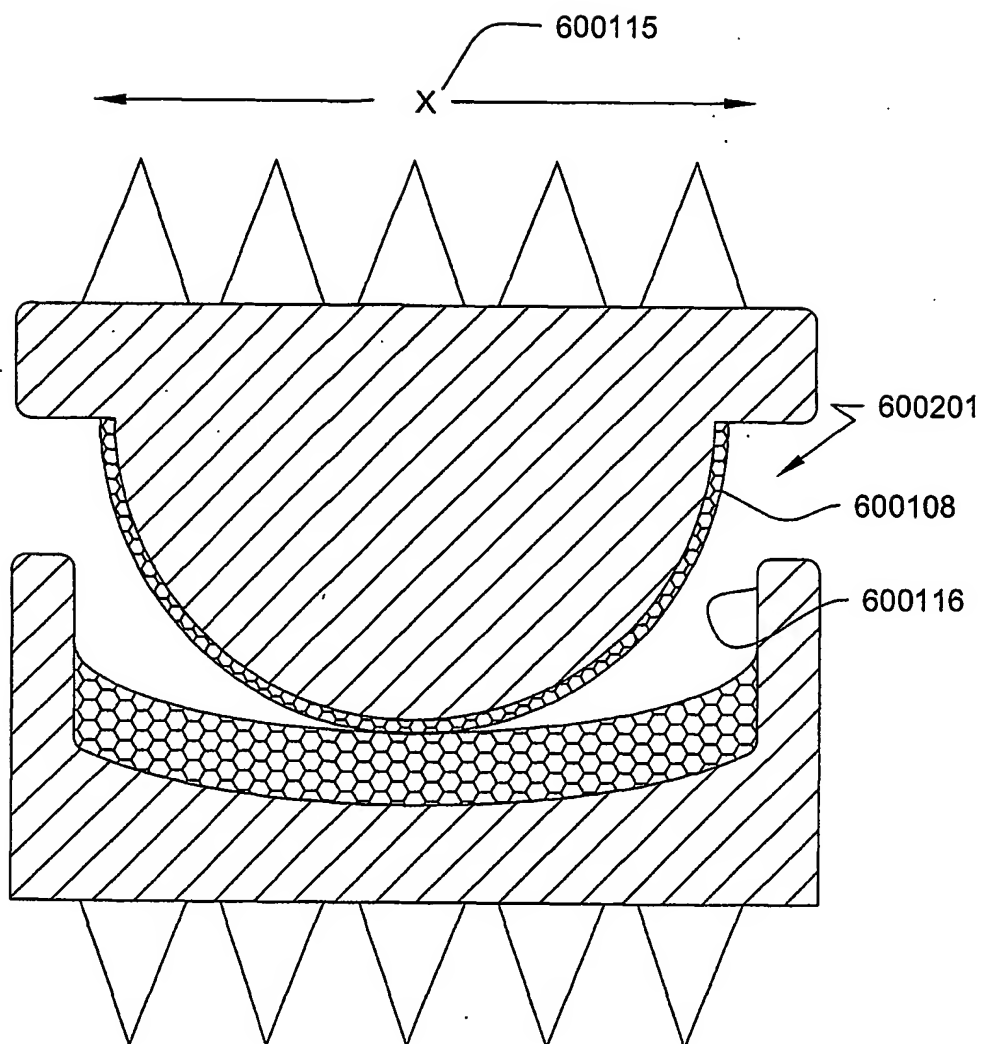


FIG. 84



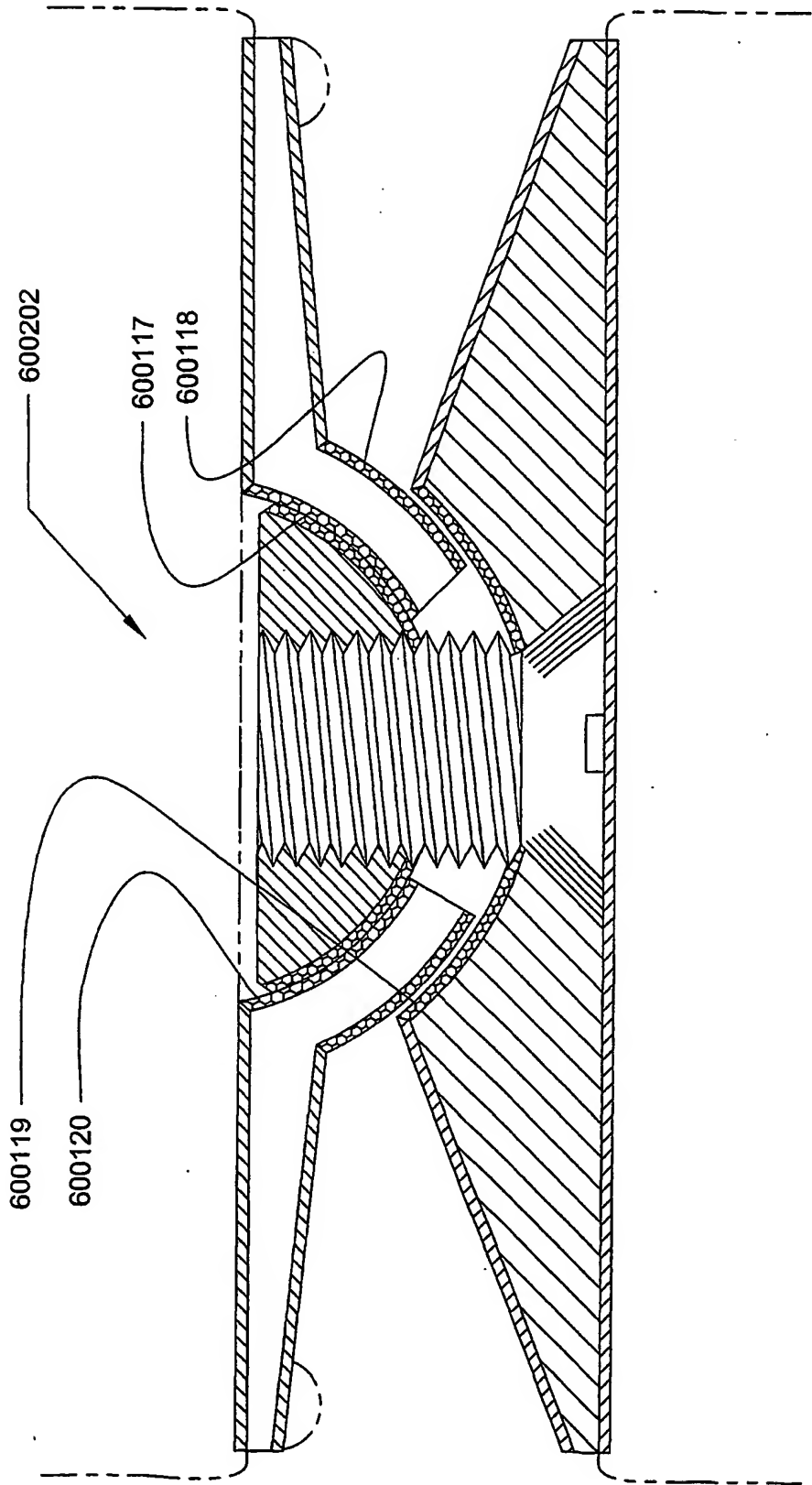


FIG. 85

FIG. 86

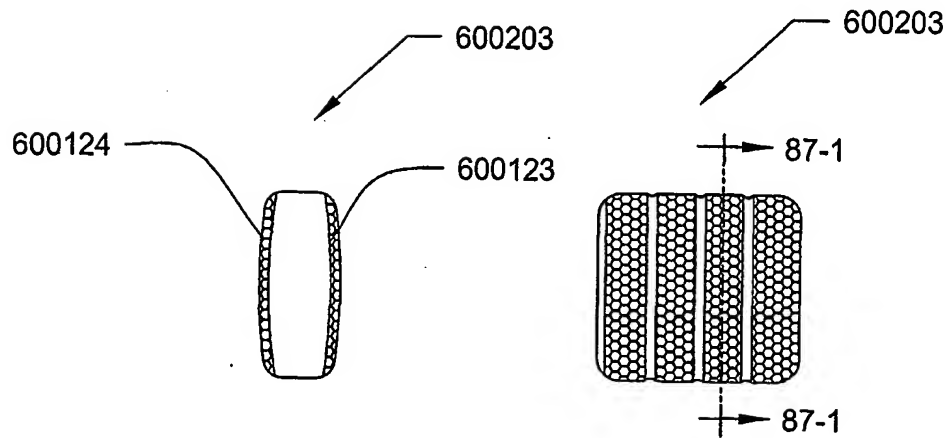
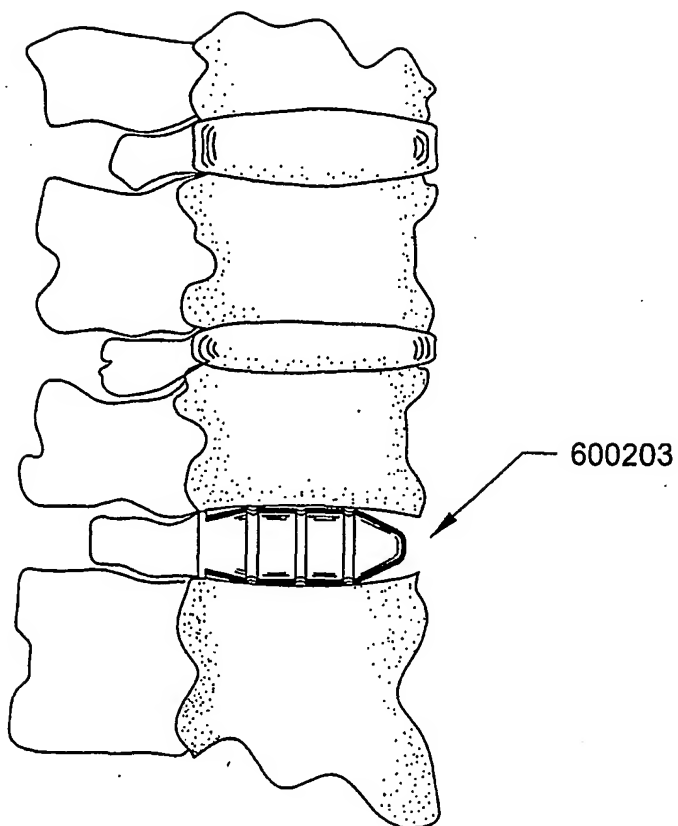


FIG. 87-1

FIG. 87

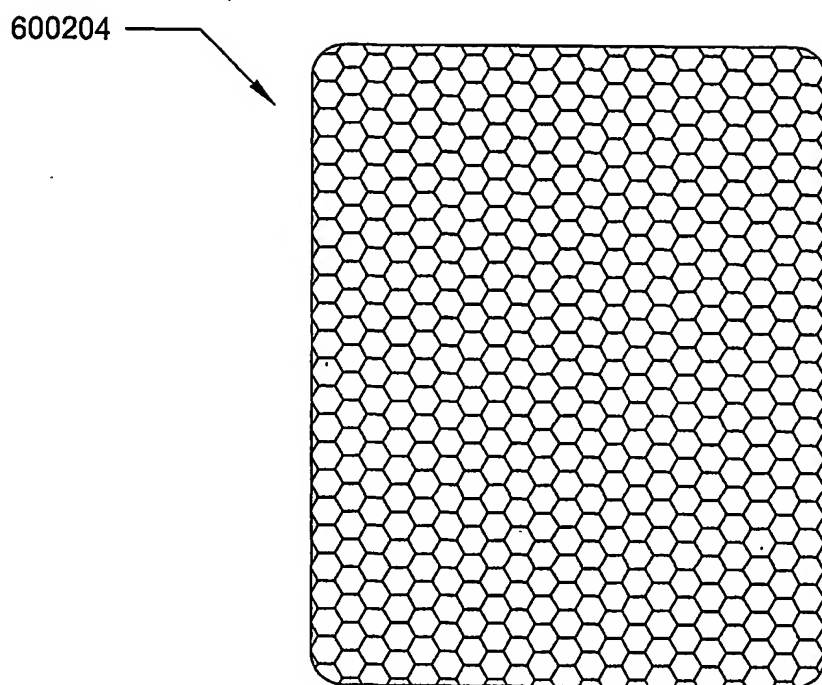
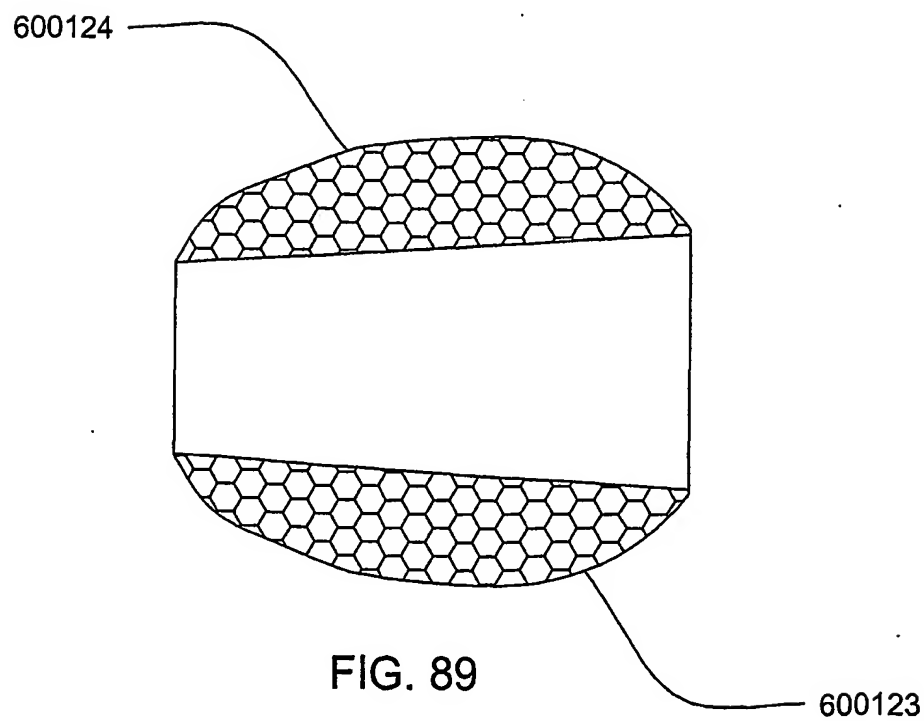


FIG. 88



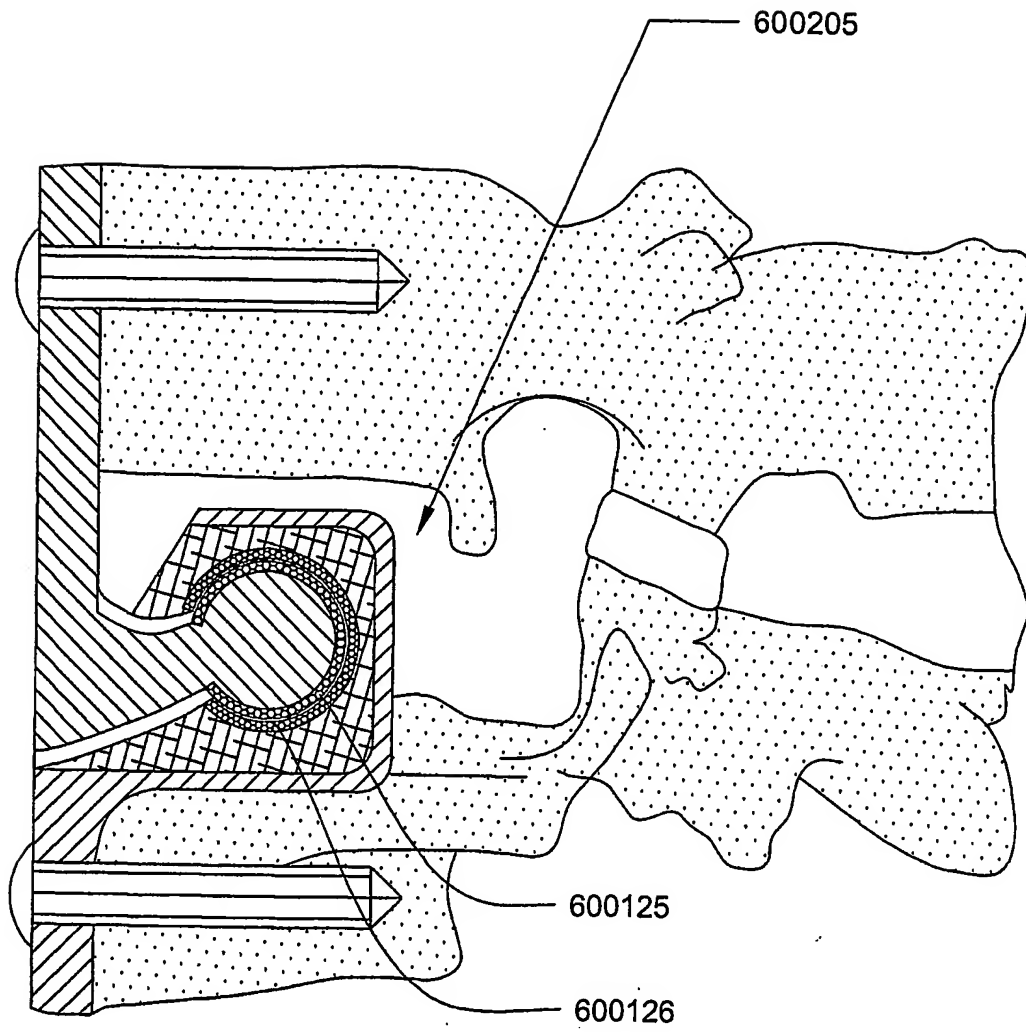


FIG. 90

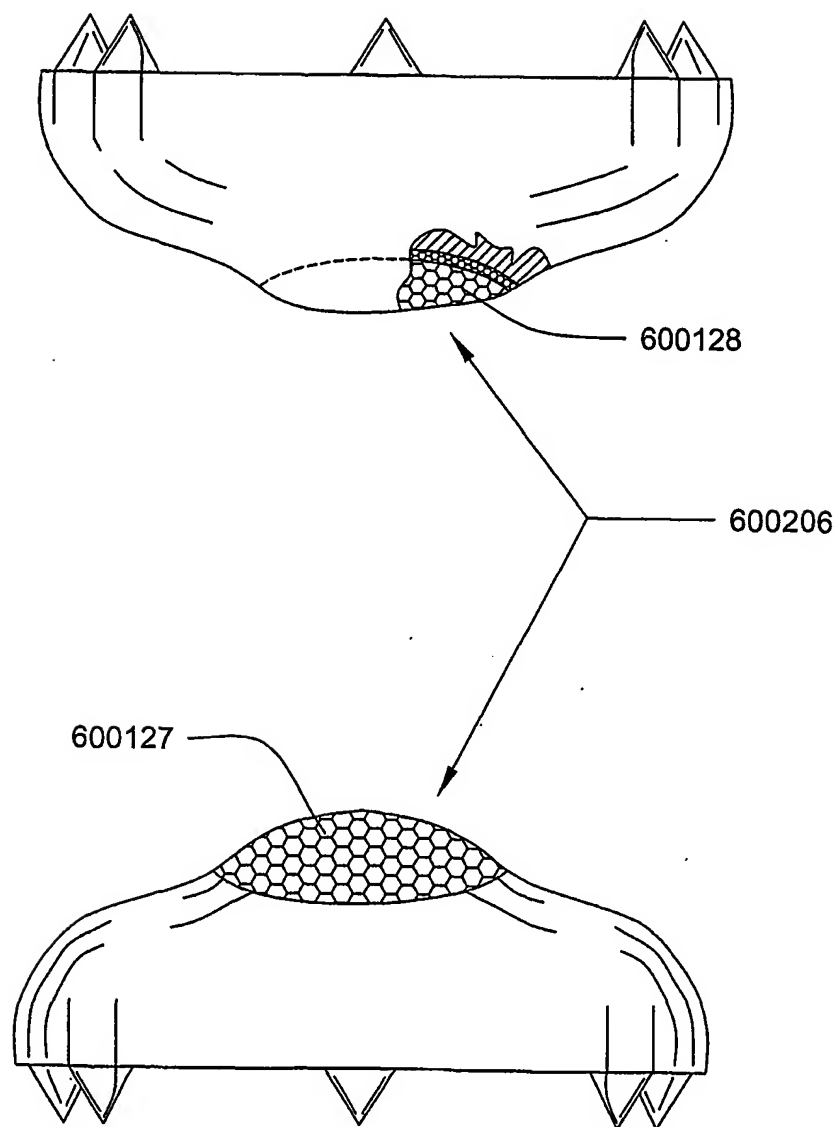


FIG.91

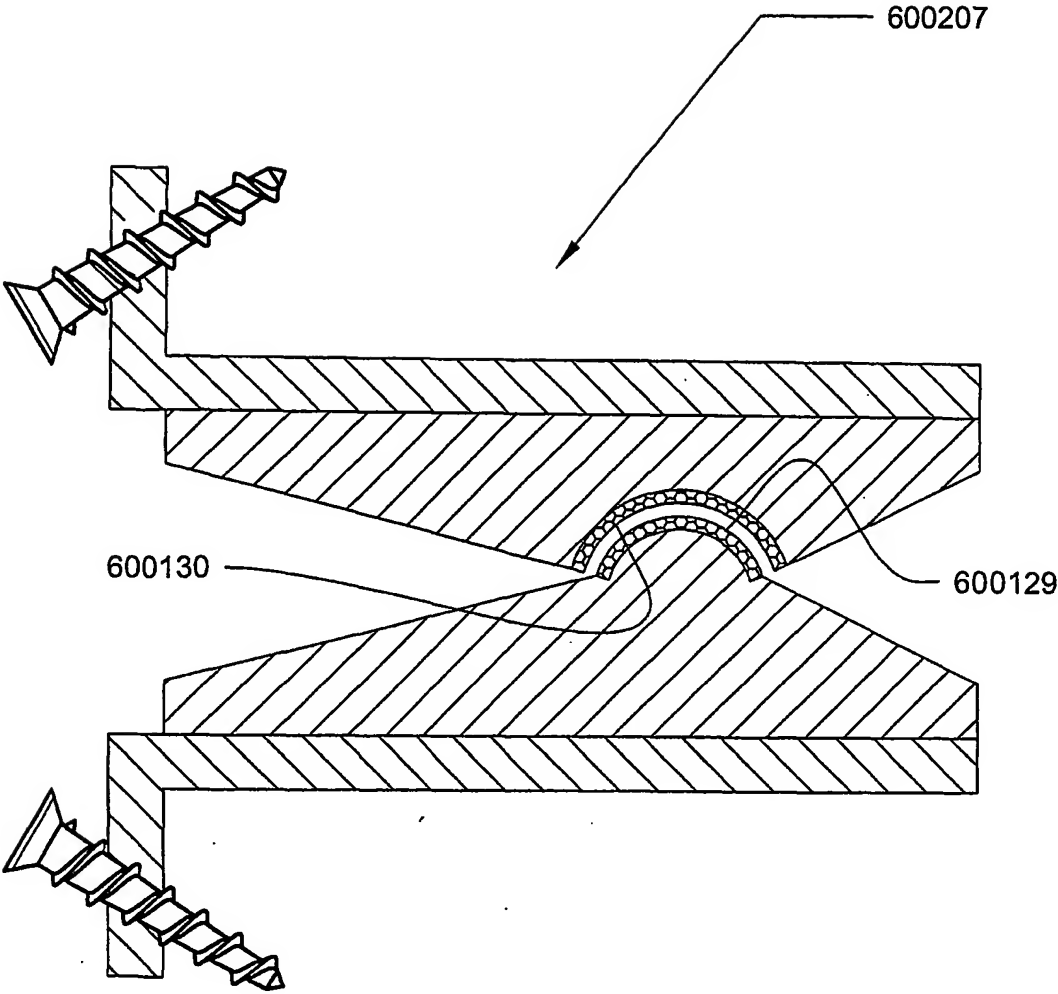
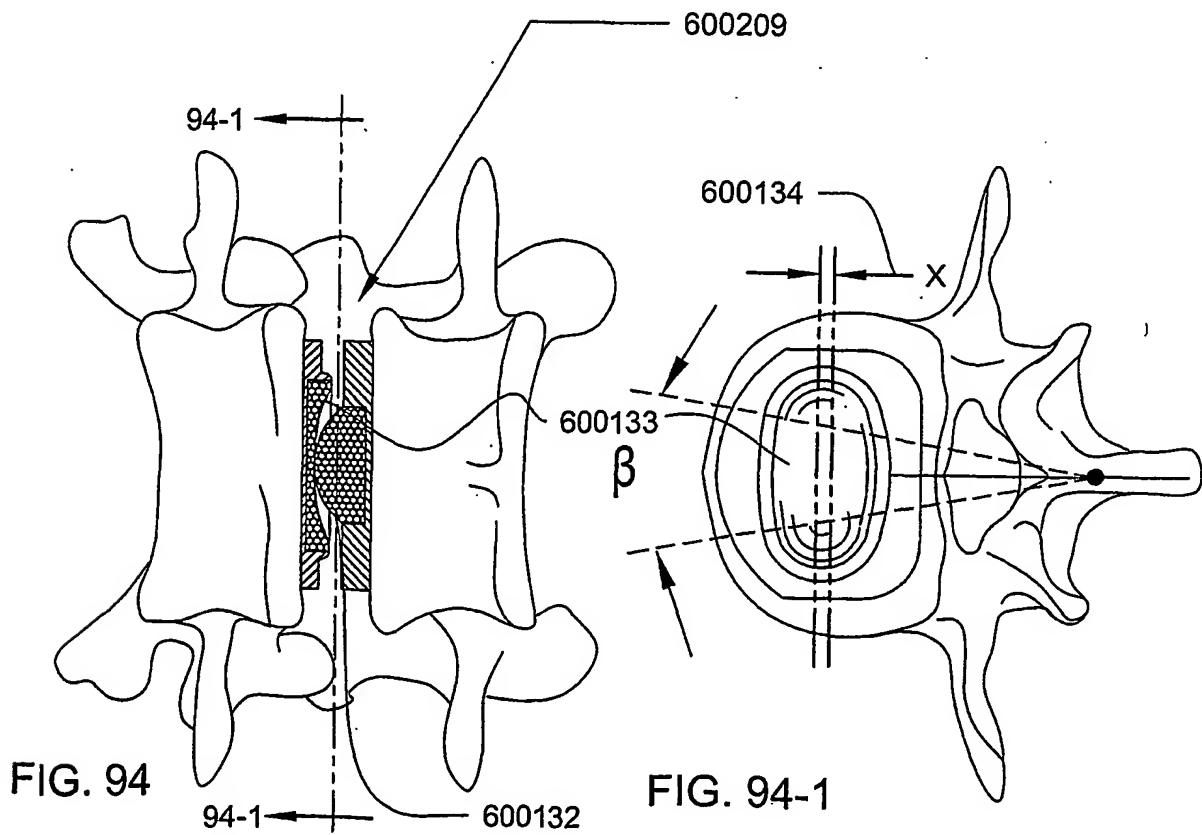
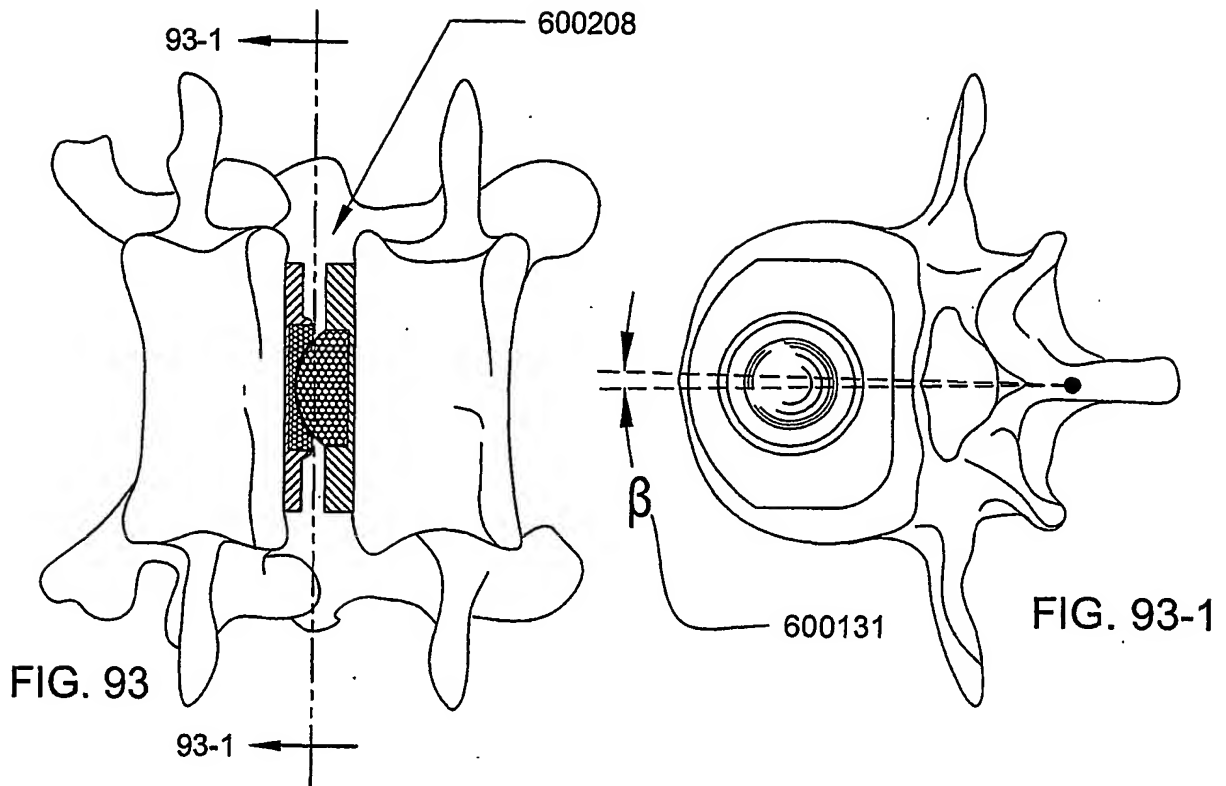
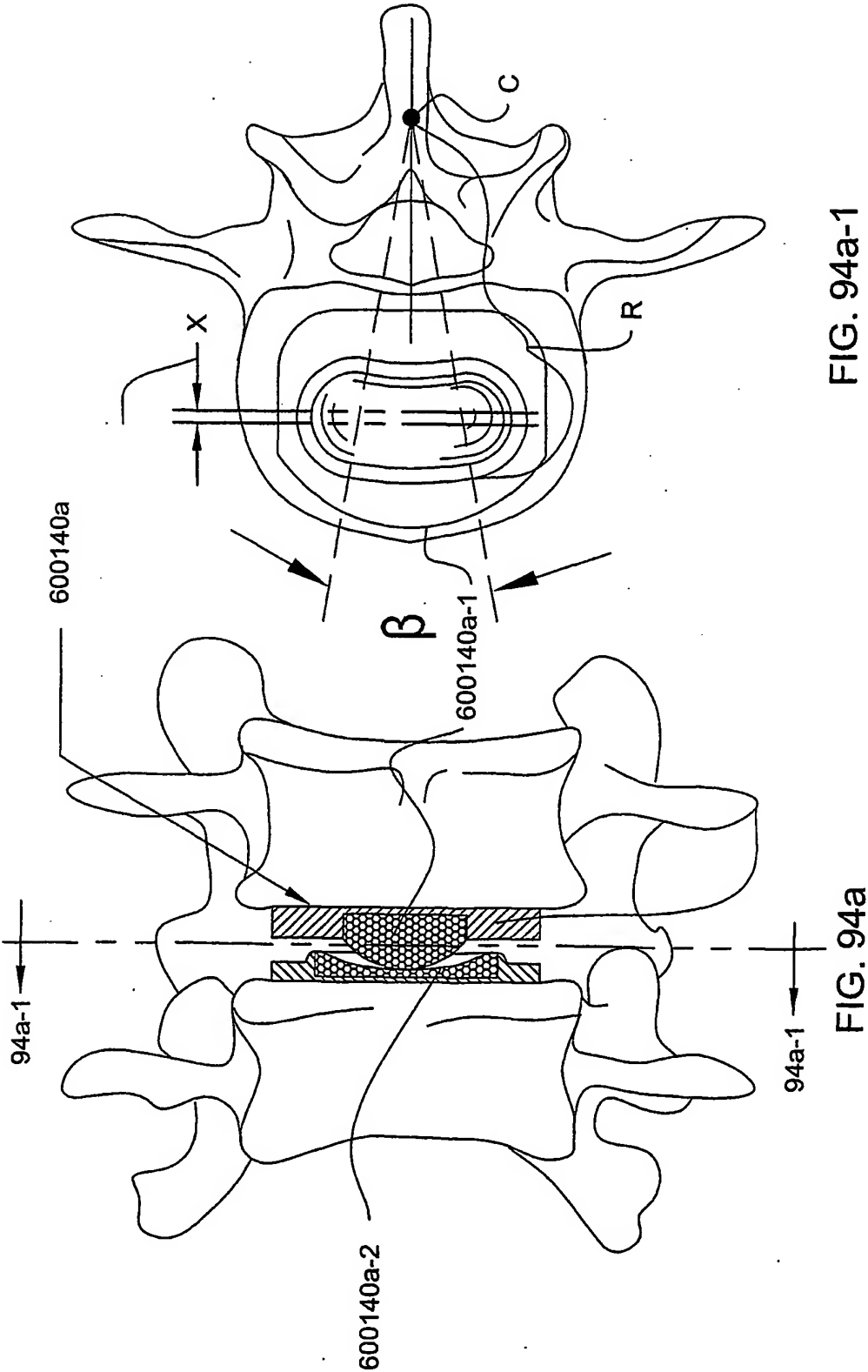


FIG.92







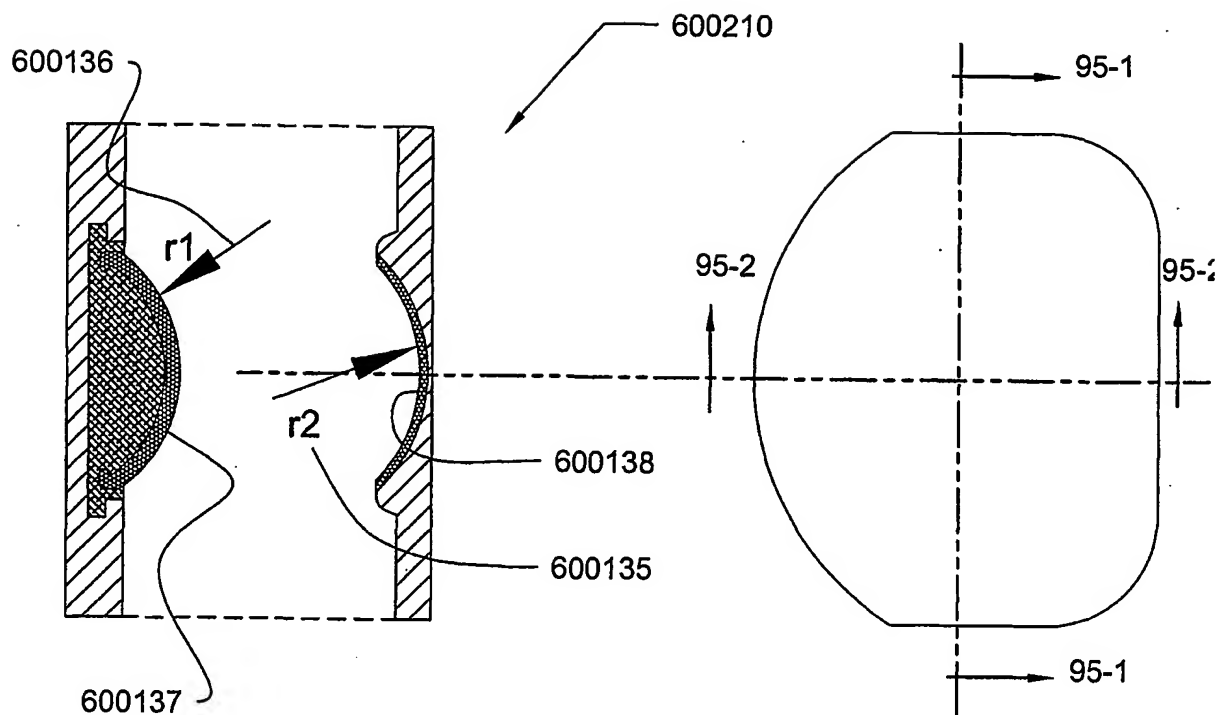


FIG. 95-1

FIG. 95

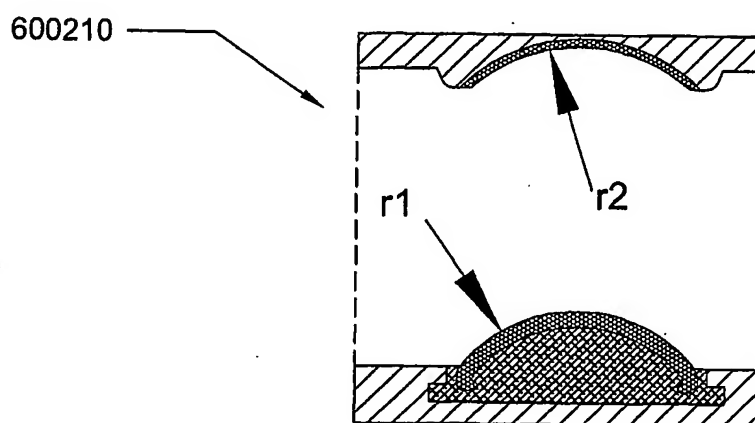


FIG. 95-2

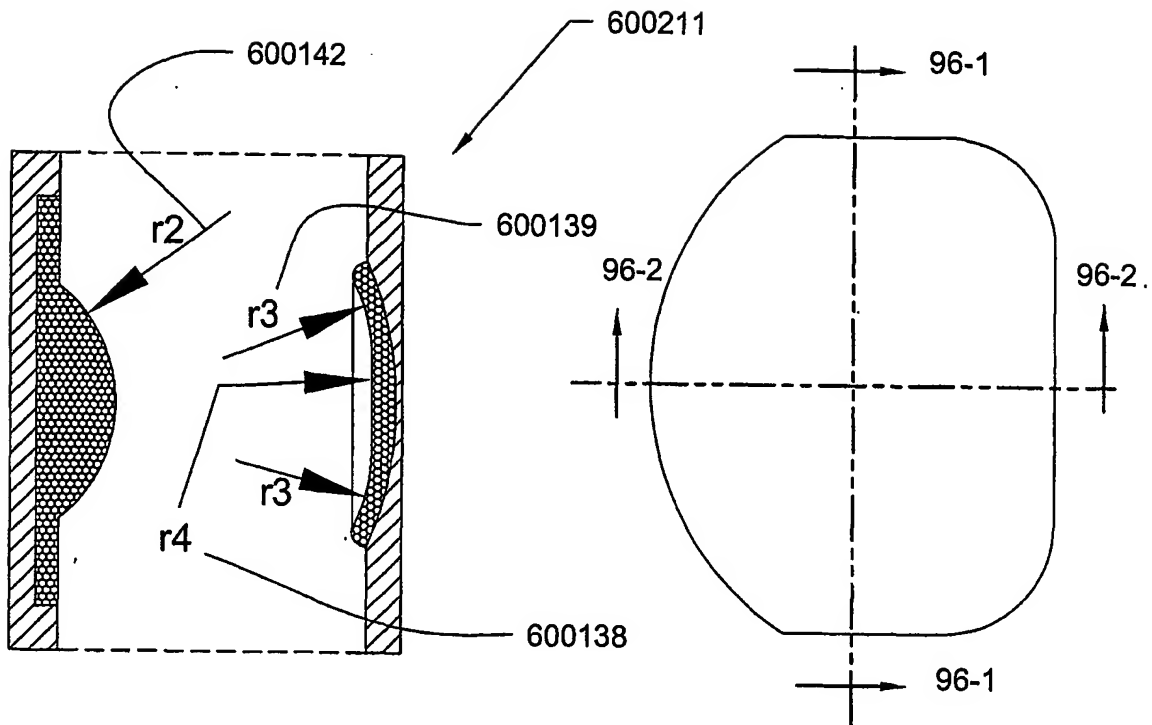


FIG. 96-1

FIG. 96

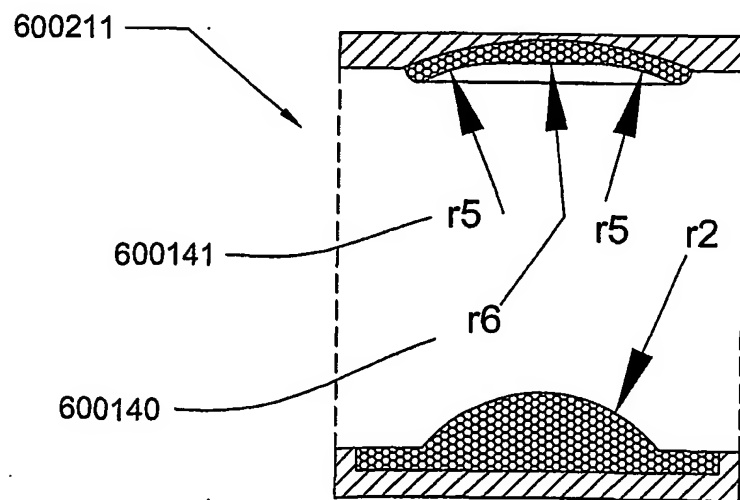


FIG. 96-2

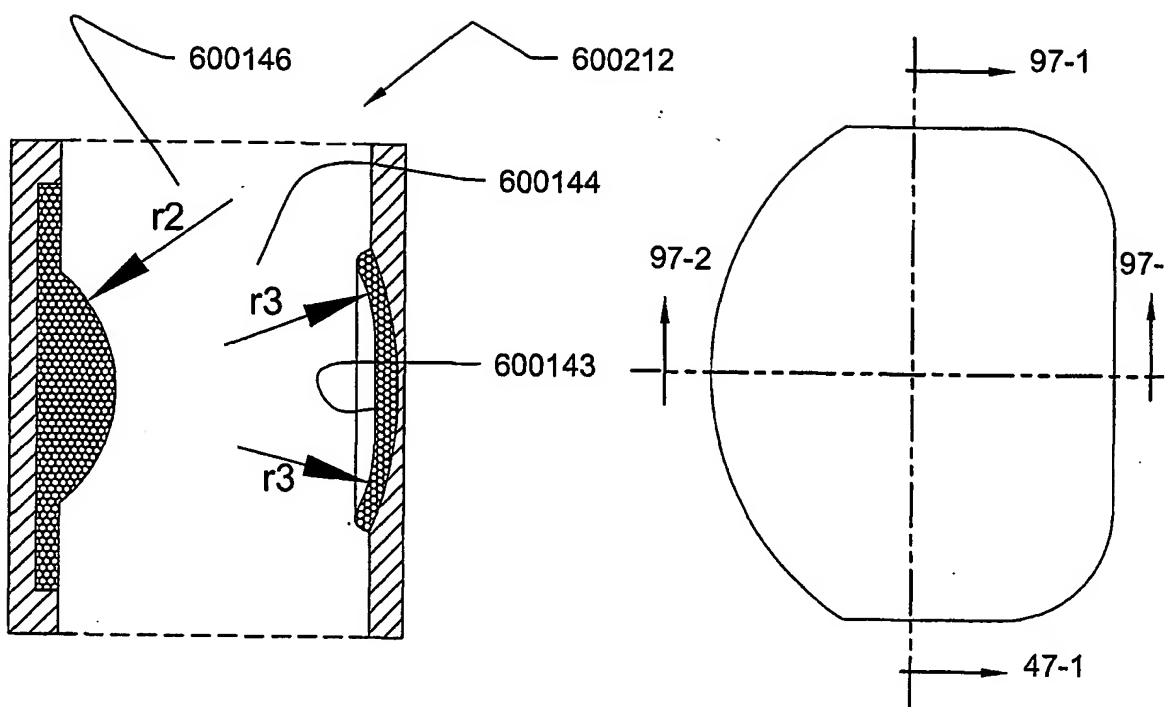


FIG. 97-1

FIG. 97

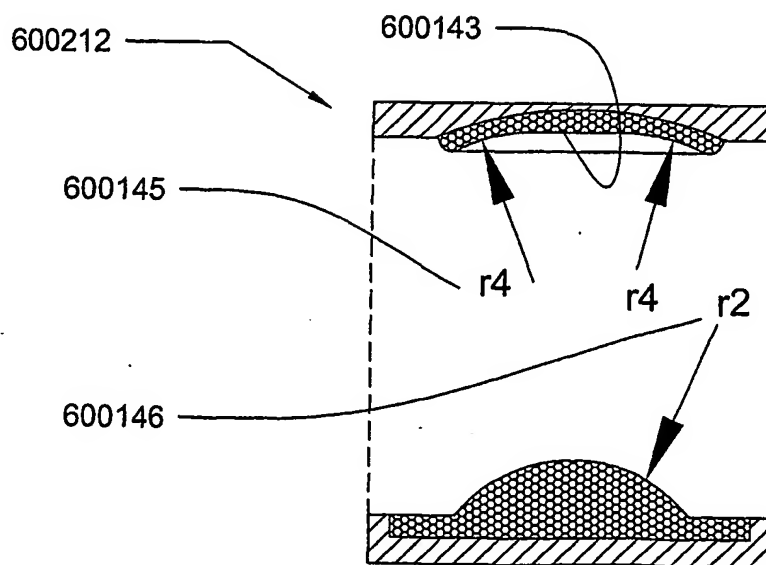


FIG. 97-2

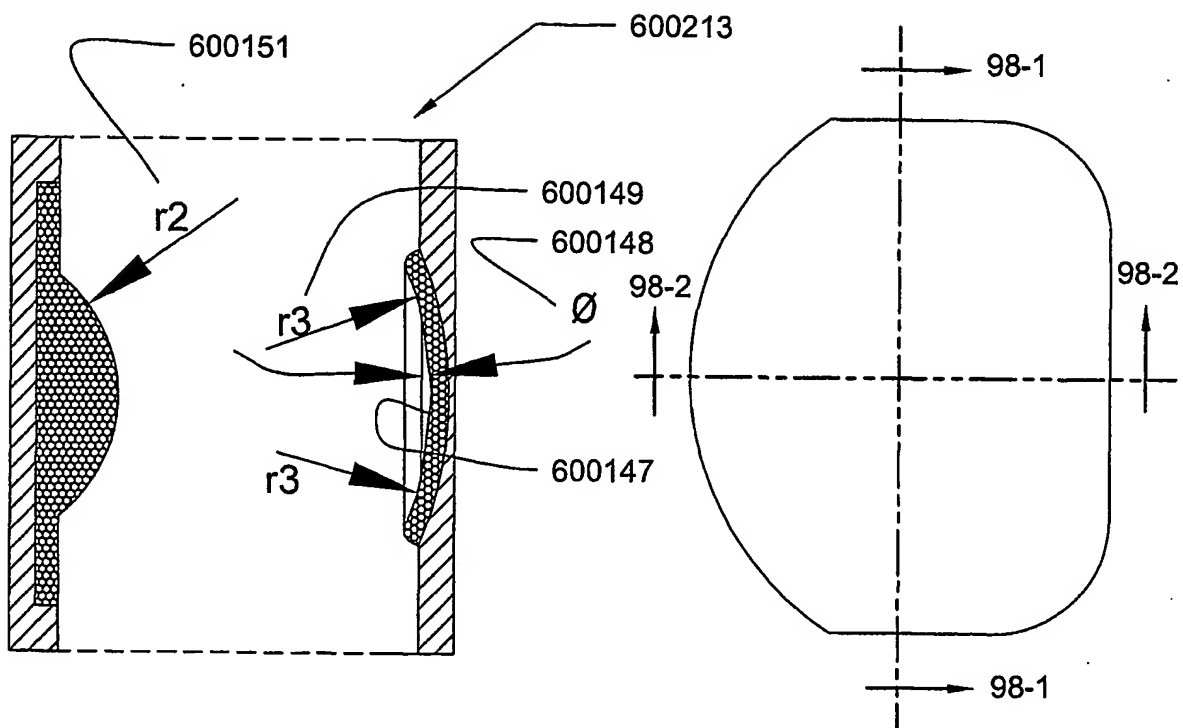


FIG. 98-1

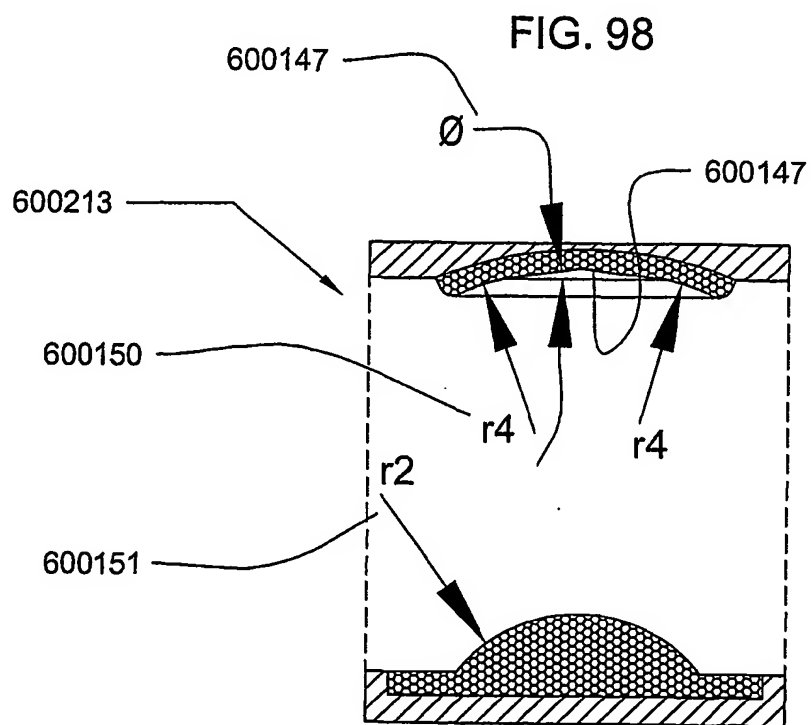


FIG. 98

FIG. 98-2

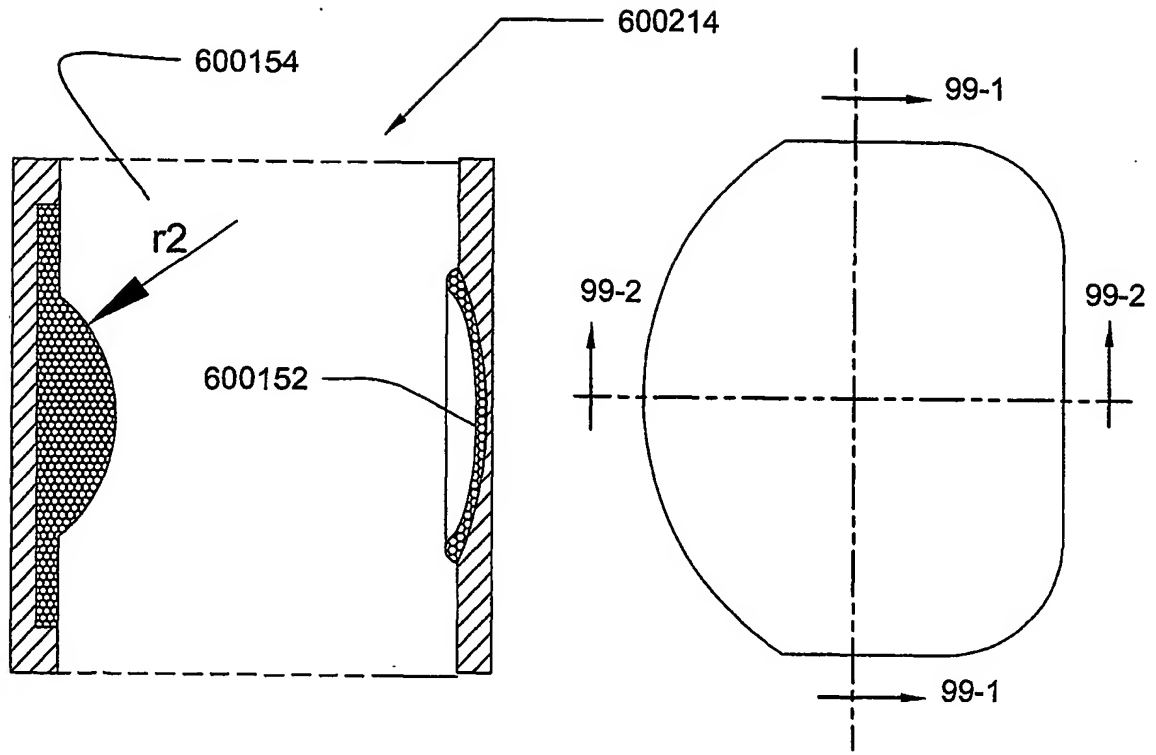


FIG. 99-1

FIG. 99

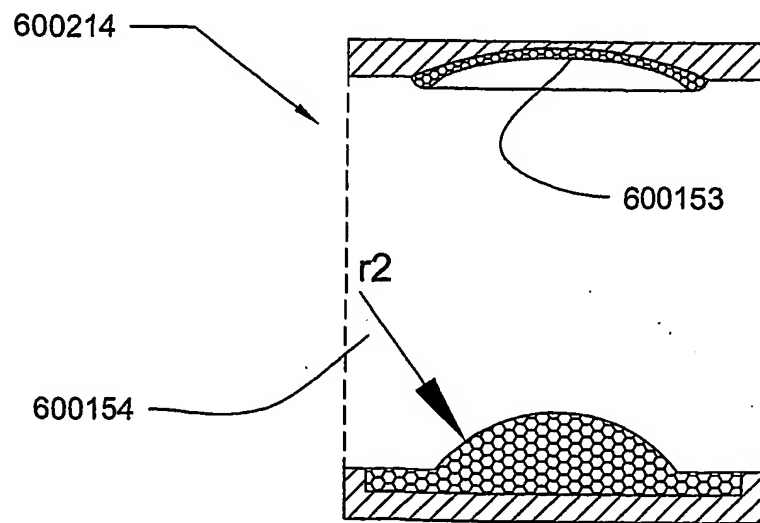


FIG. 99-2

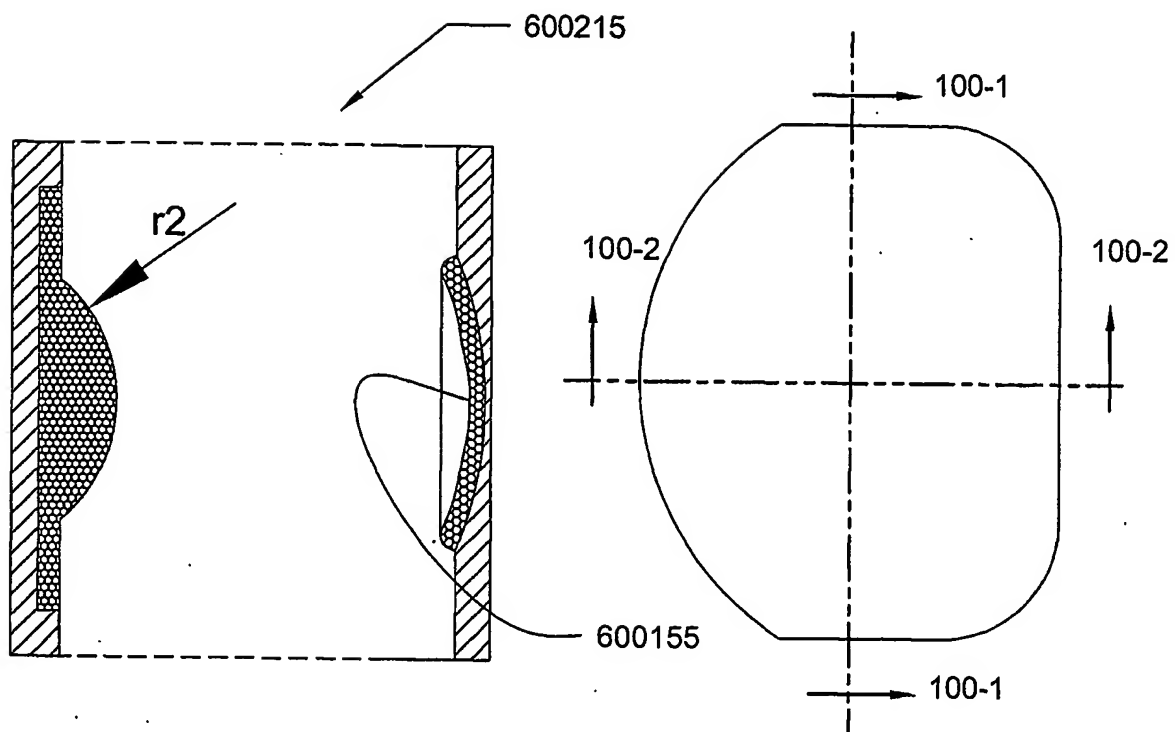


FIG.100-1

FIG. 100

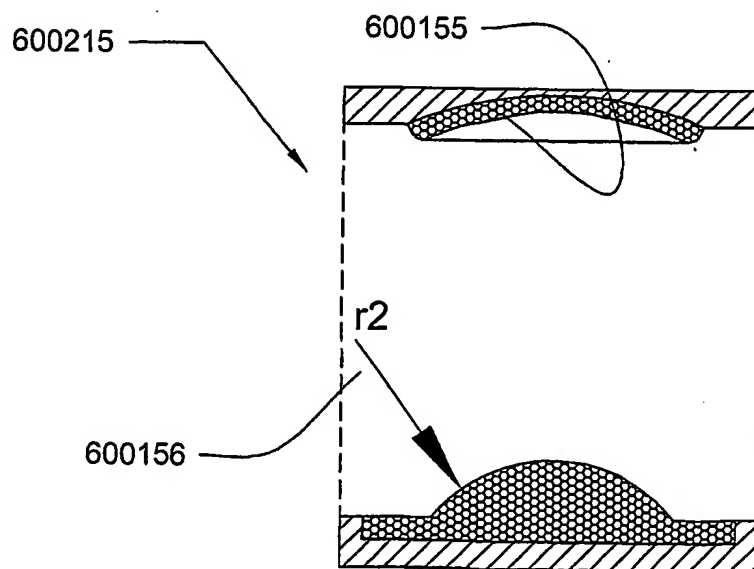


FIG. 100-2

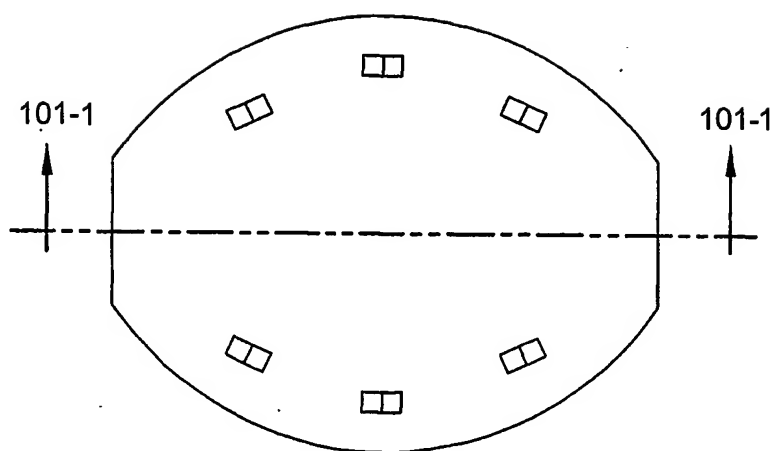


FIG. 101

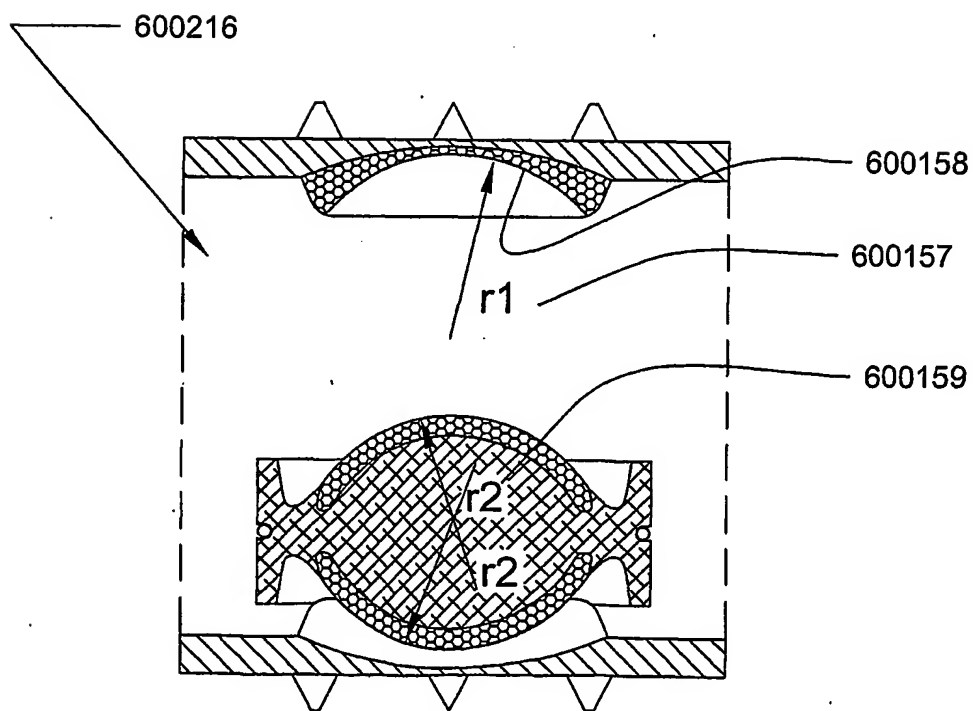


FIG. 101-1

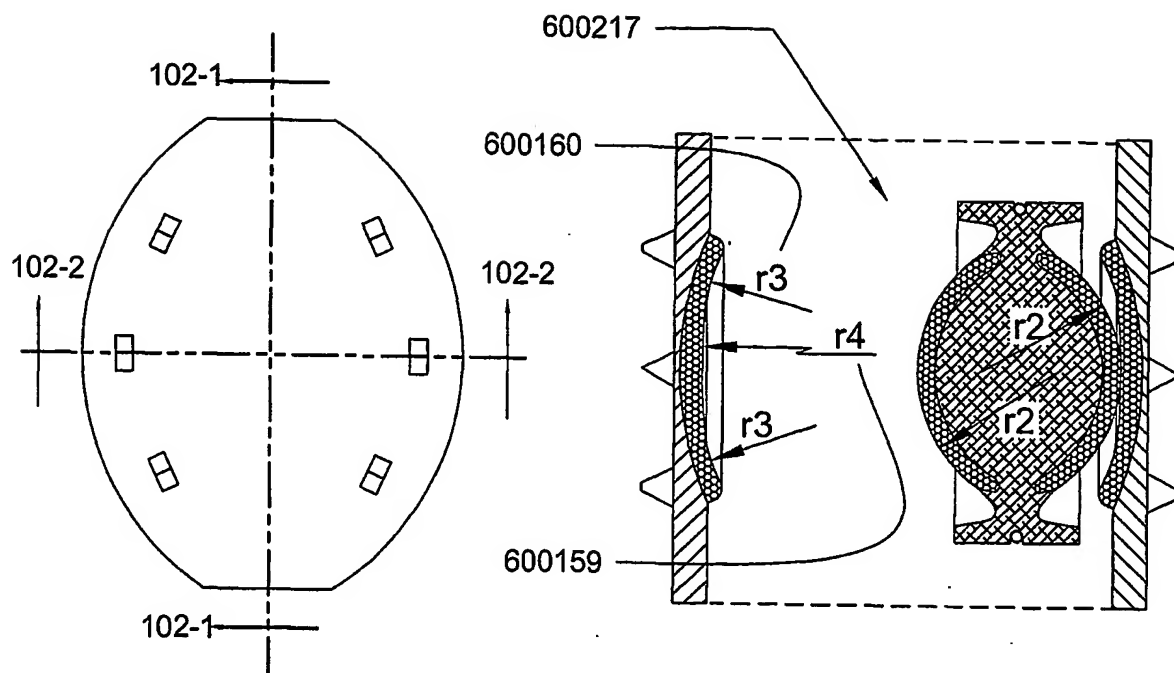


FIG.102

FIG. 102-1

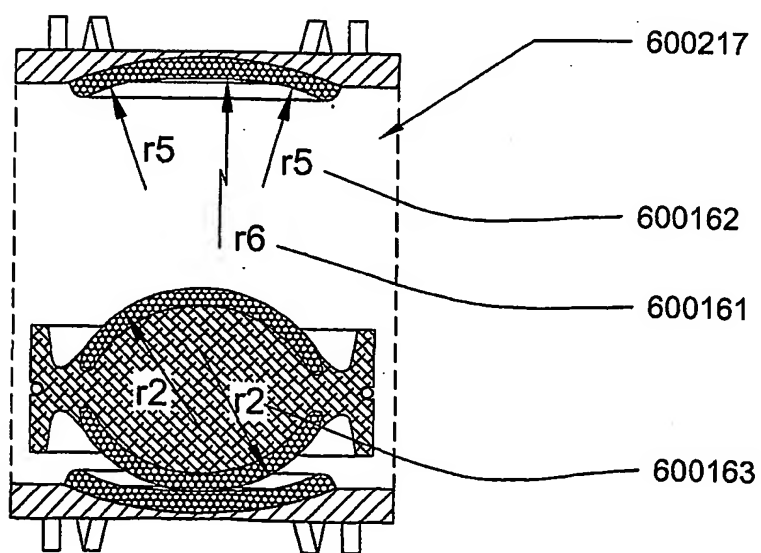


FIG. 102-2



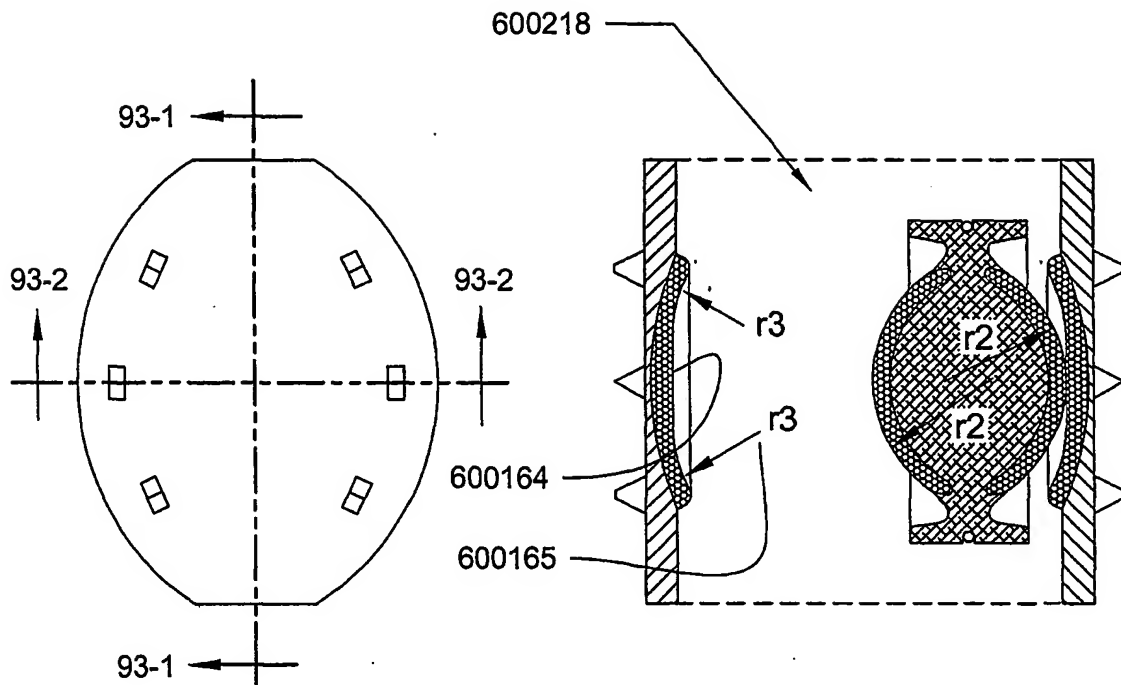


FIG. 103

FIG. 103-1

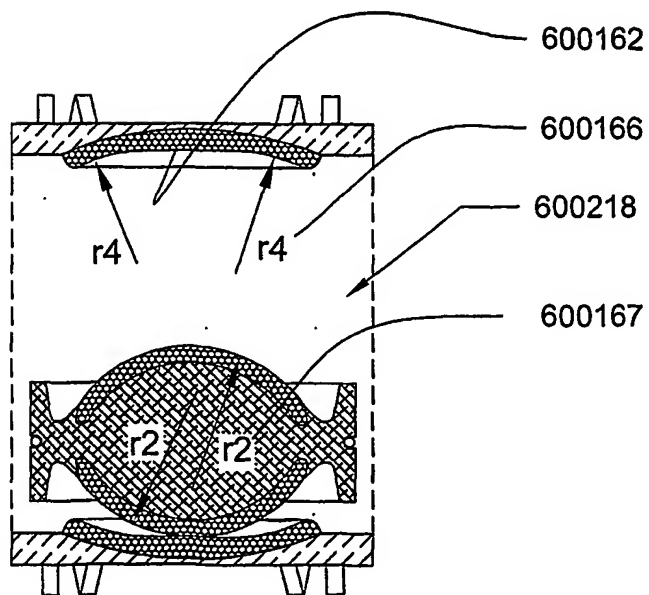


FIG. 103-2

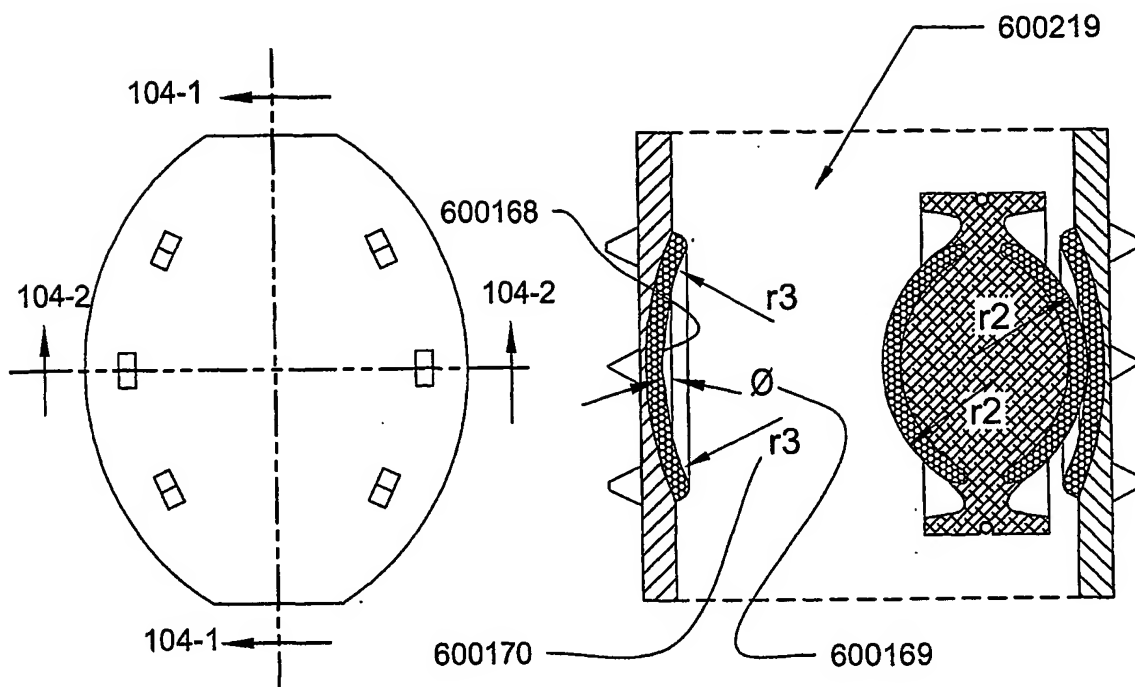


FIG. 104

FIG. 104-1

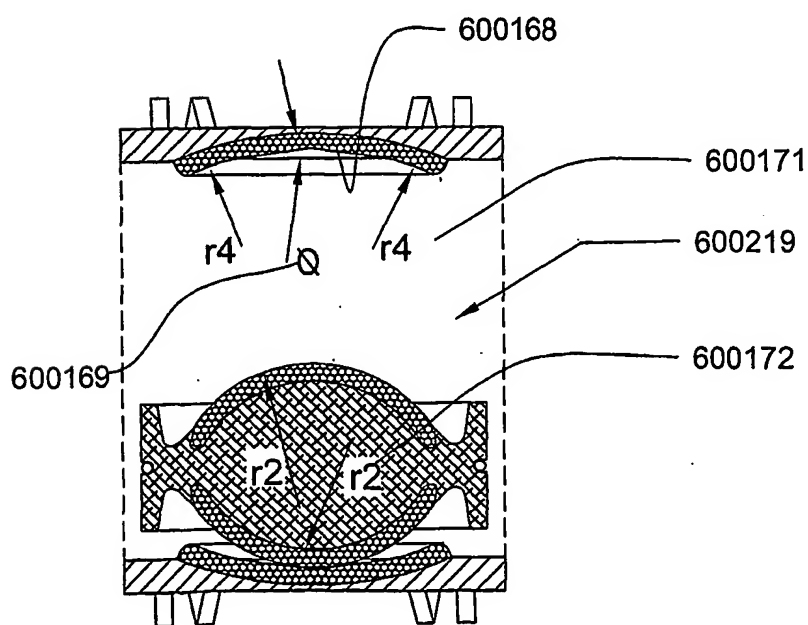


FIG. 104-2

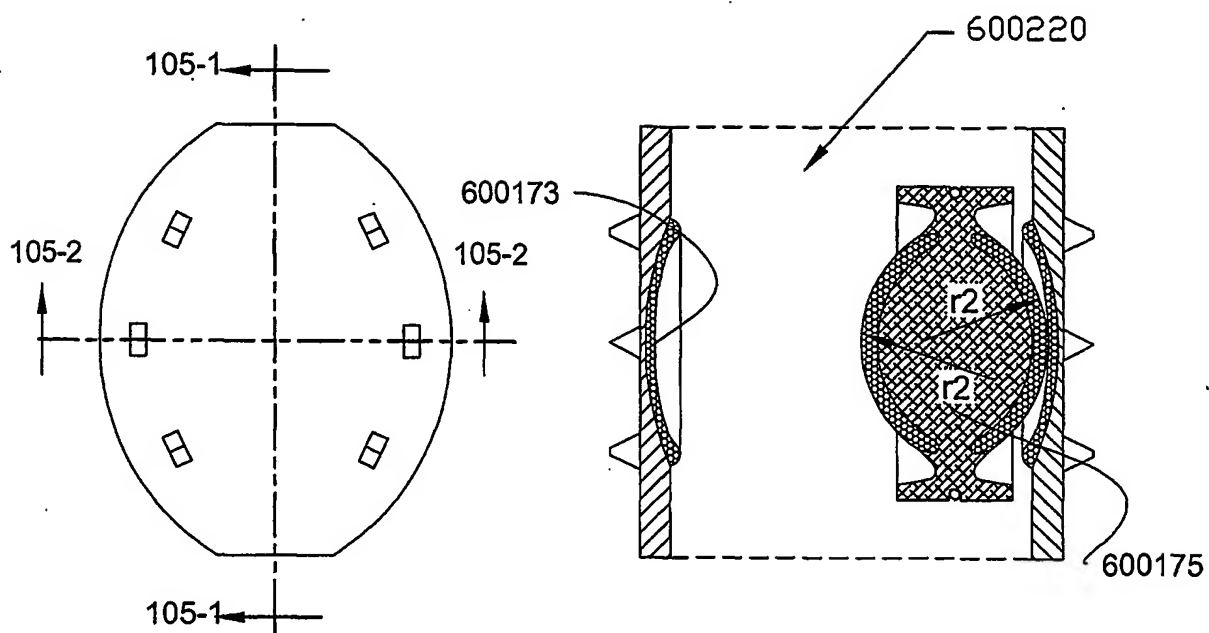


FIG. 105

FIG. 105-1

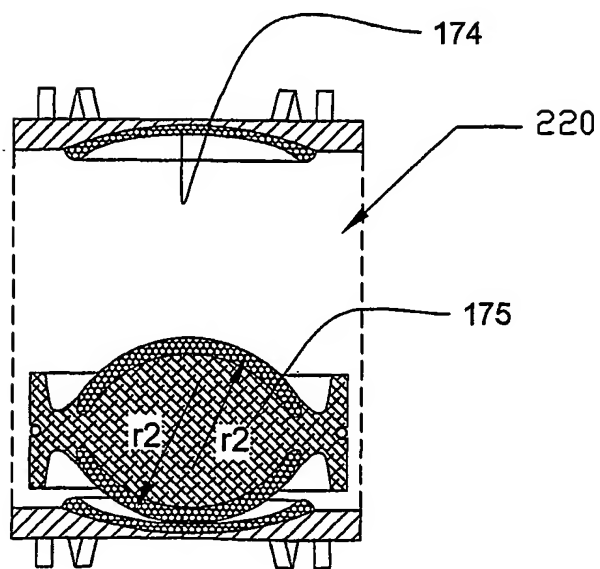


FIG. 105-2

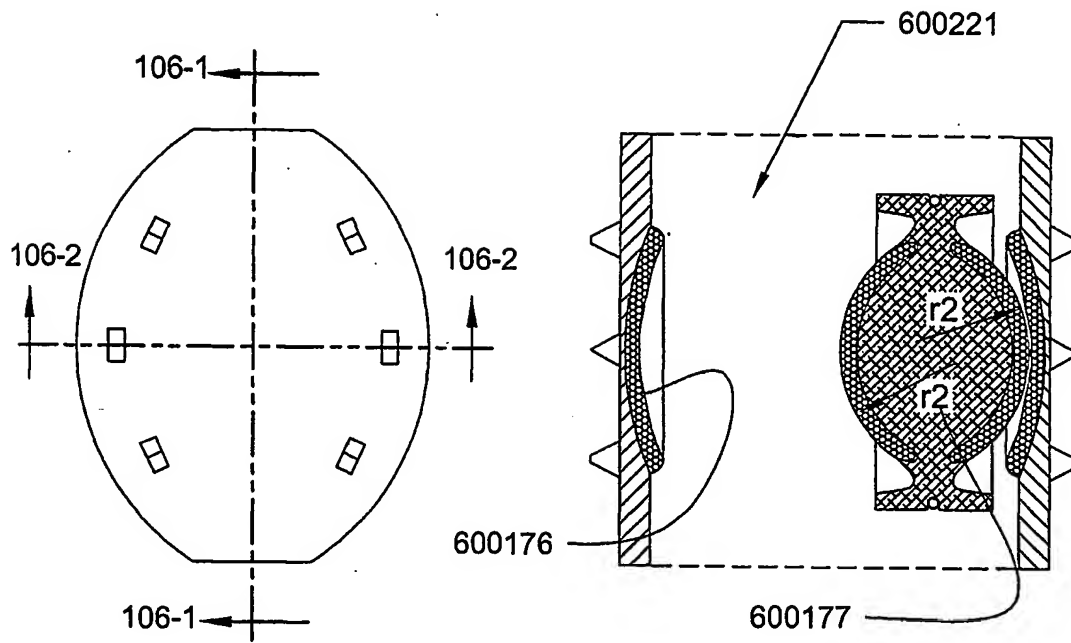


FIG. 106

FIG. 106-1

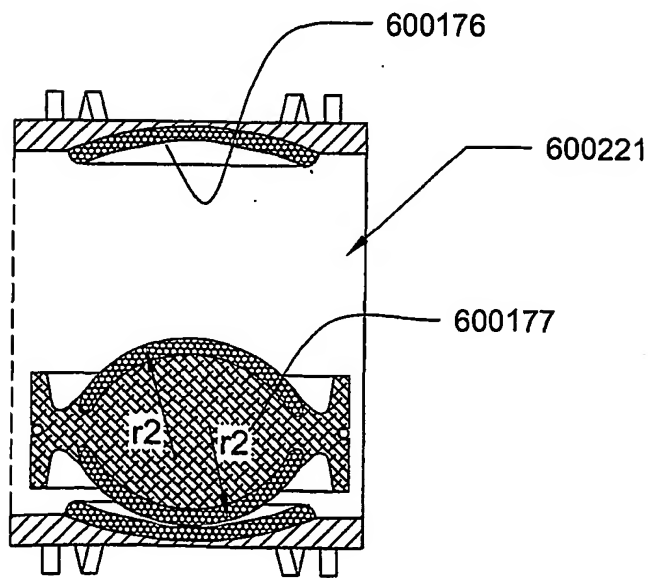


FIG. 106-2

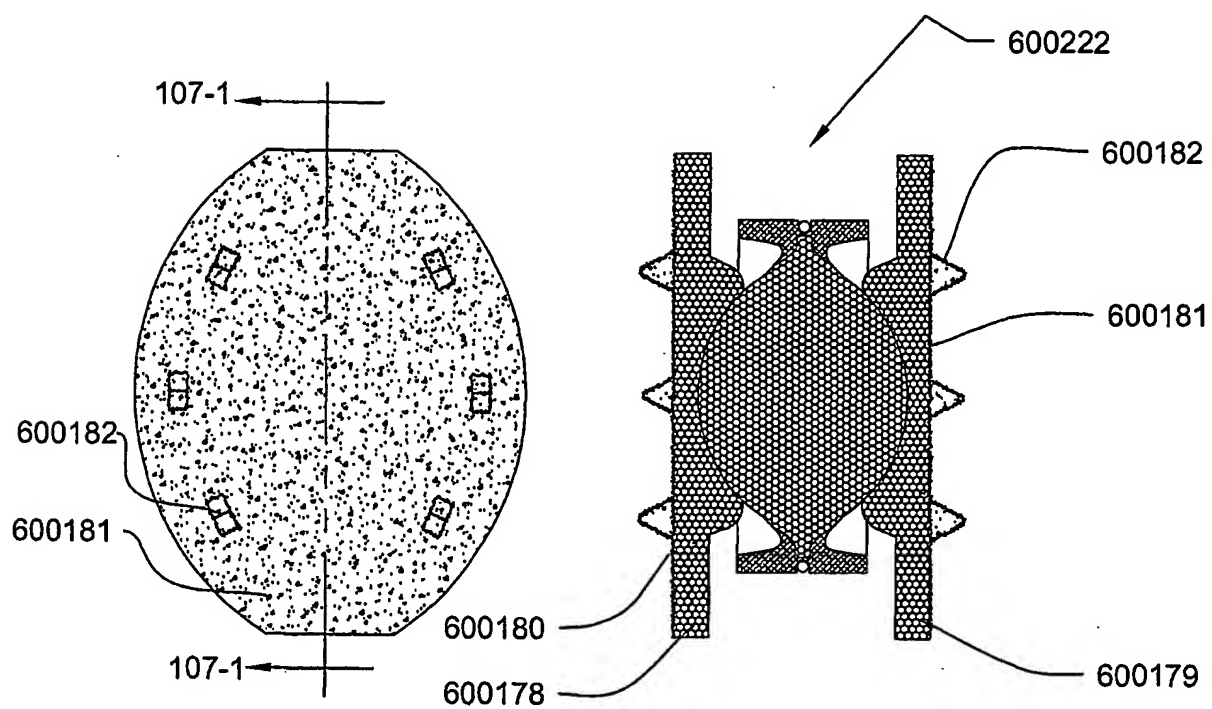


FIG. 107

FIG. 107-1

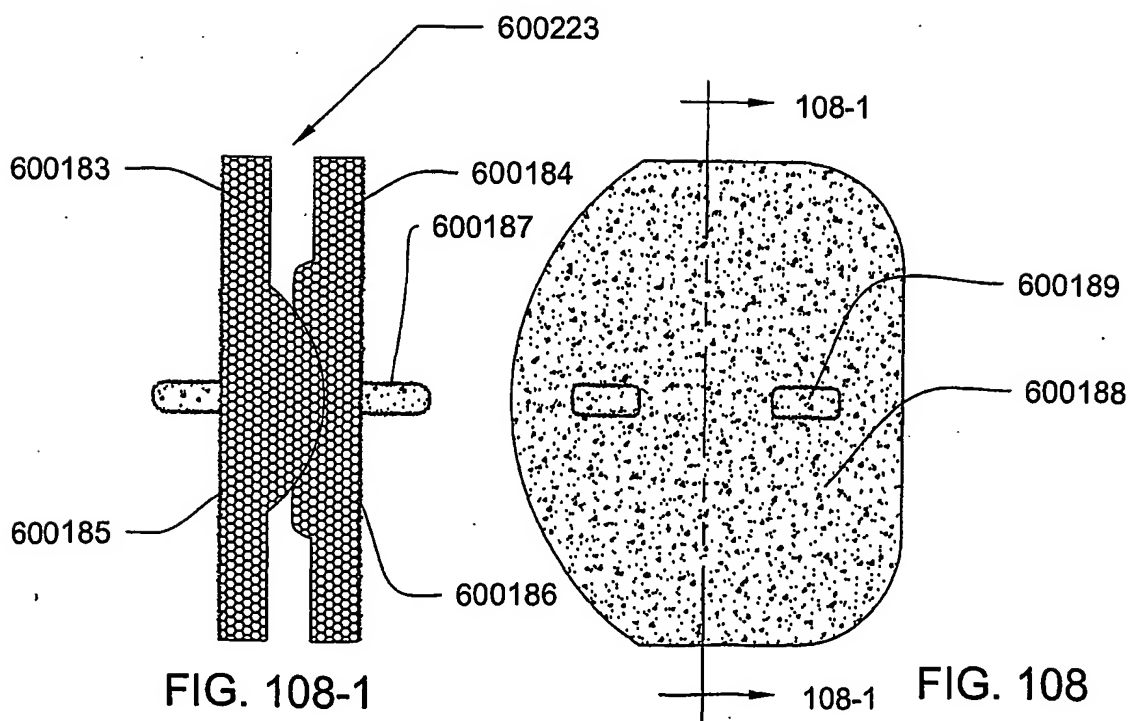
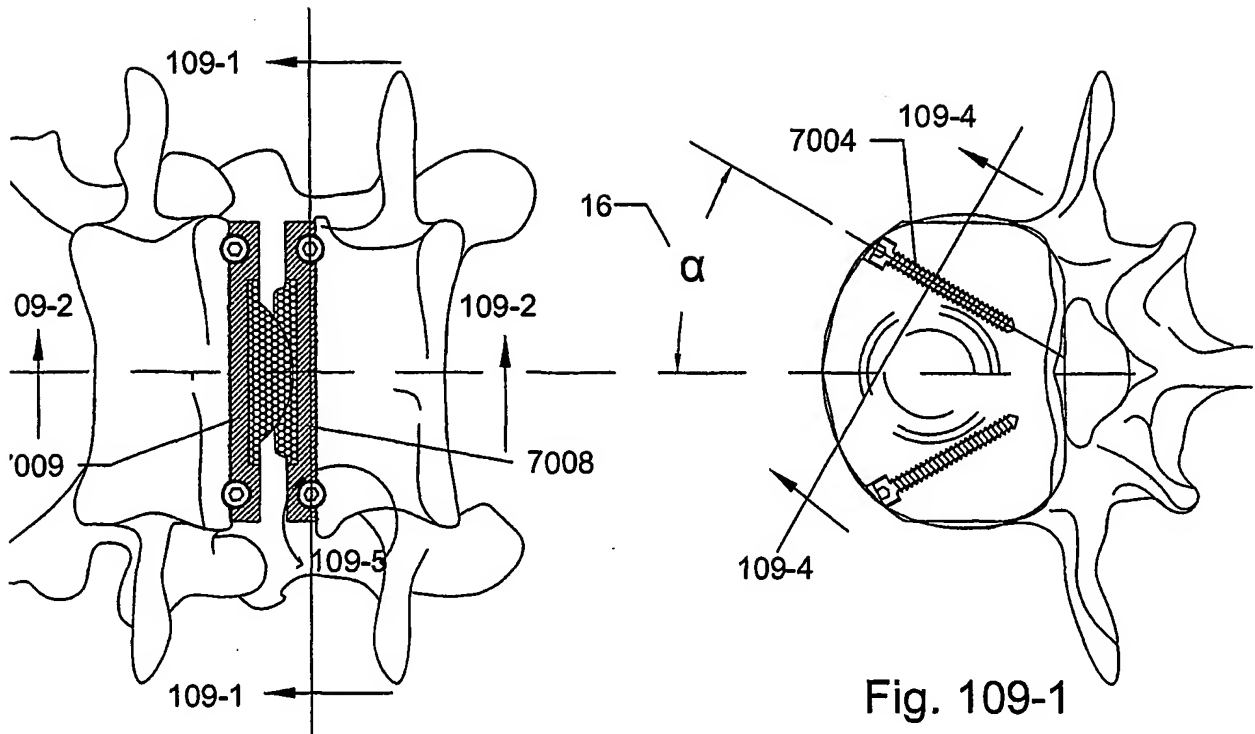
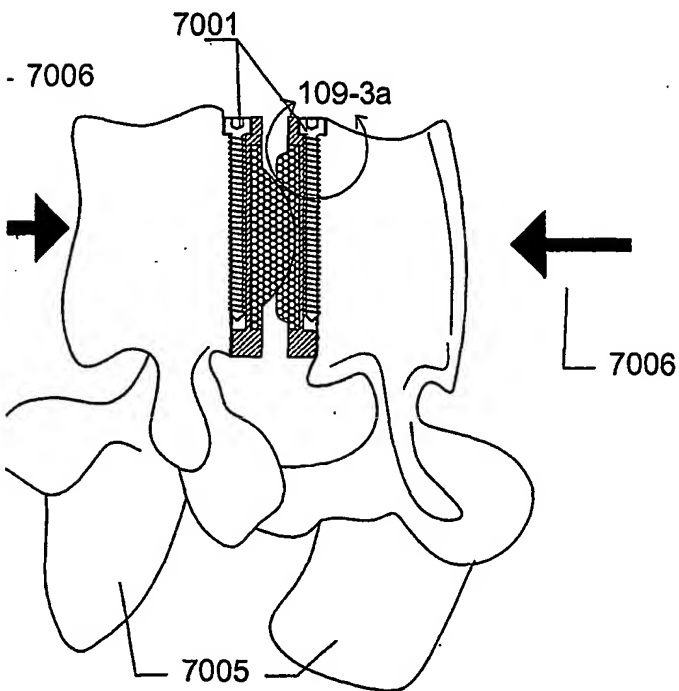


FIG. 108-1

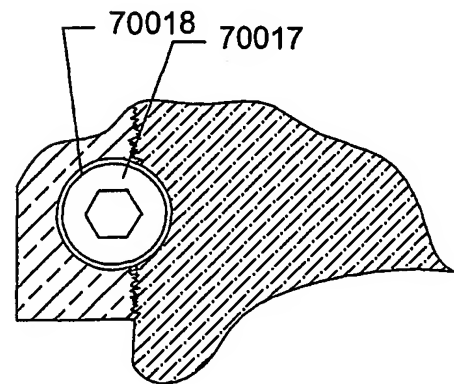
FIG. 108



**Fig. 109**



**Fig. 109-2**



**Fig. 109-5**

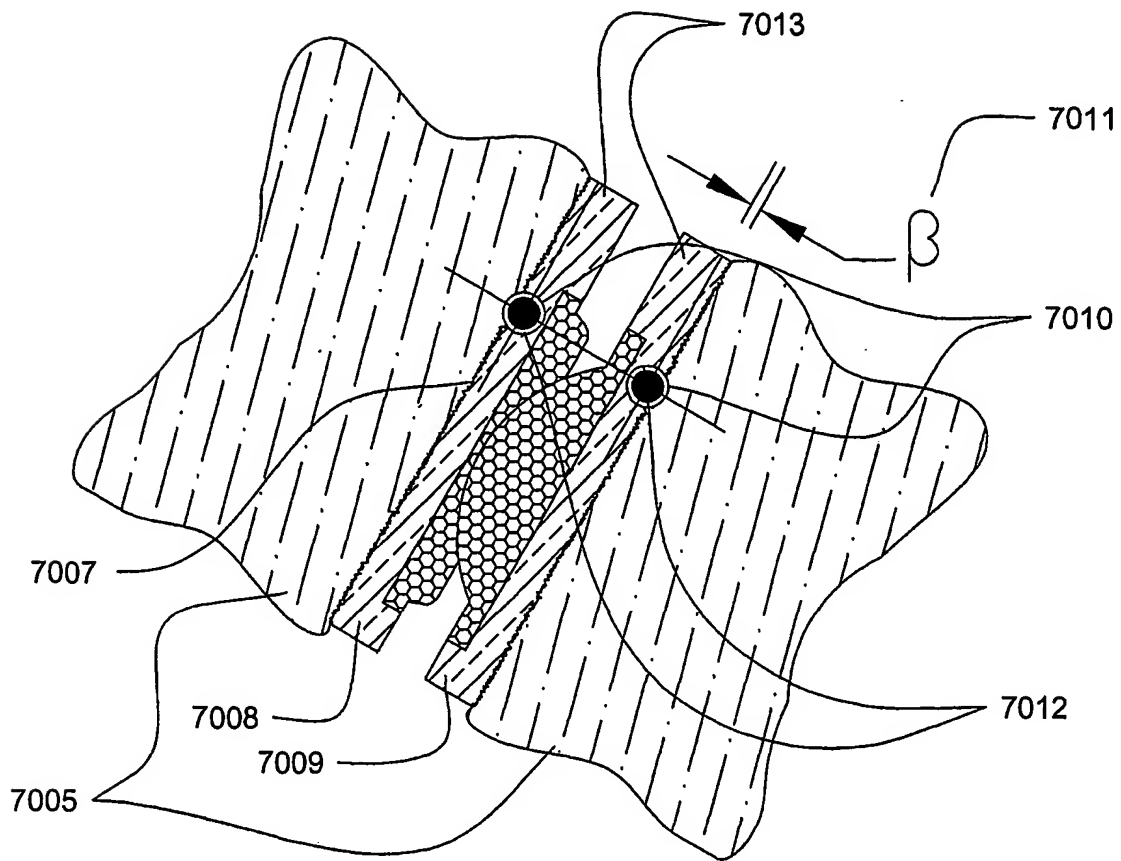


Fig. 109-4

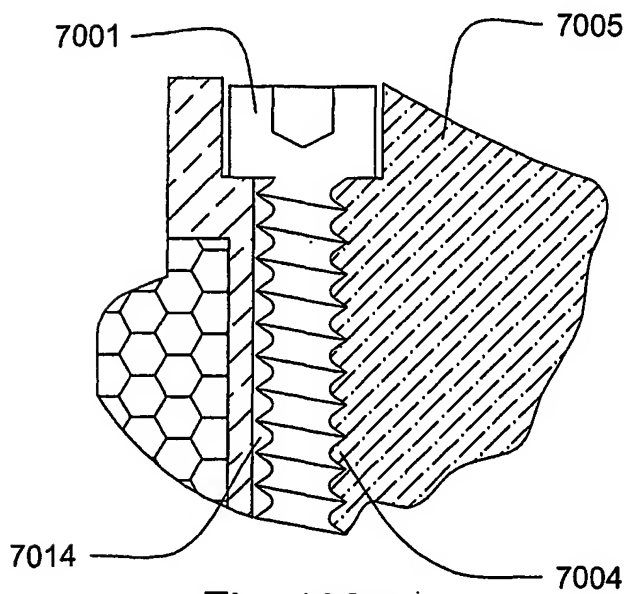


Fig. 109-3a

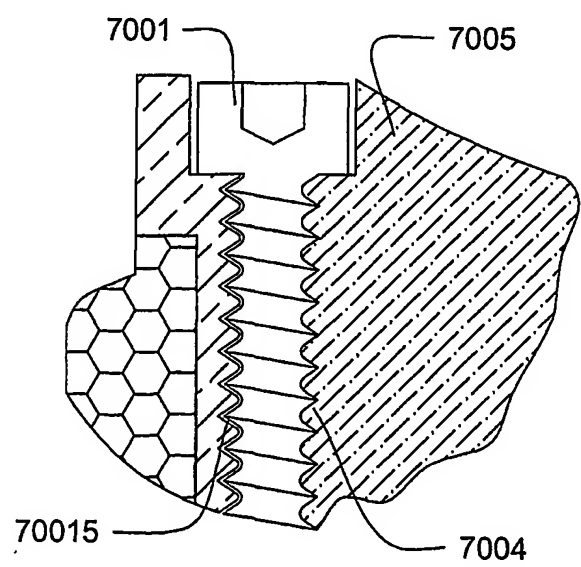


Fig. 109-36

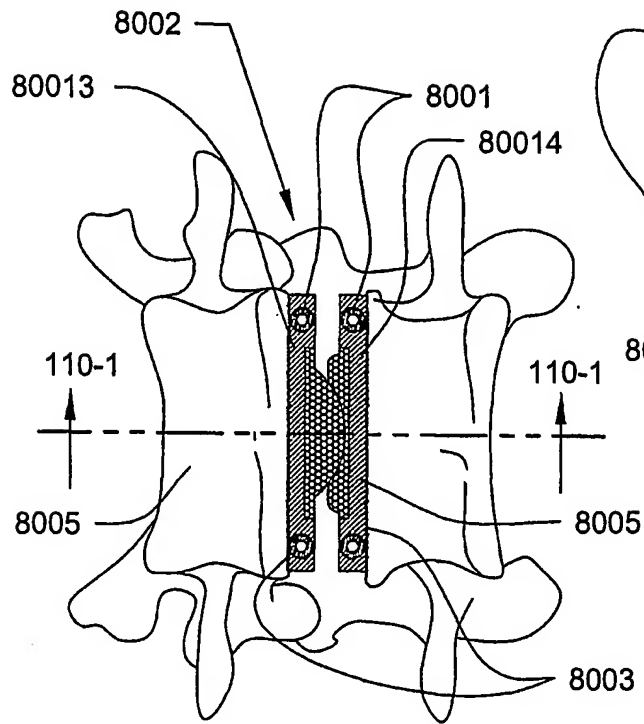


Fig. 110

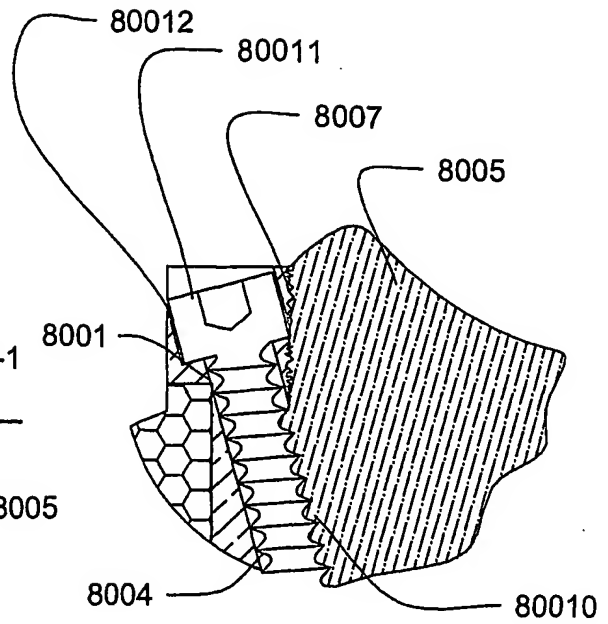


Fig. 110-3

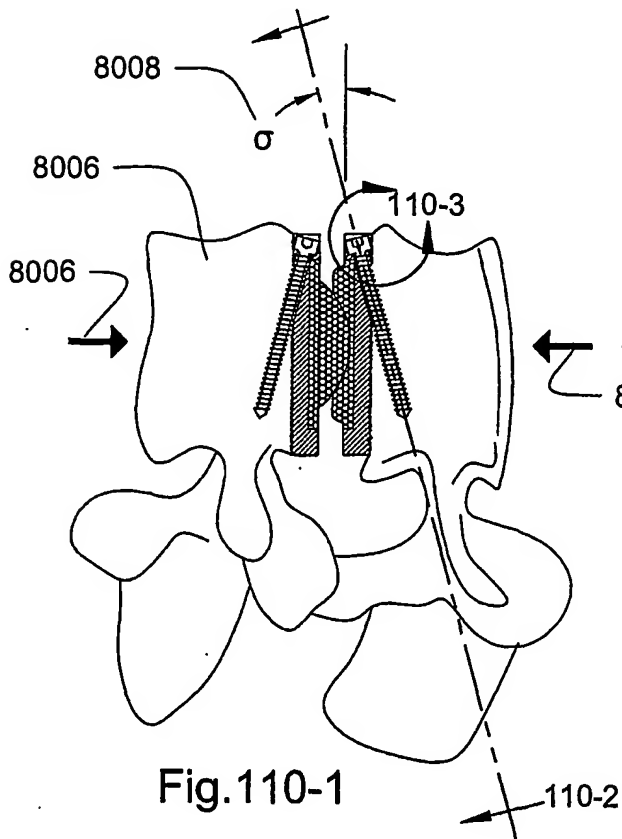


Fig. 110-1

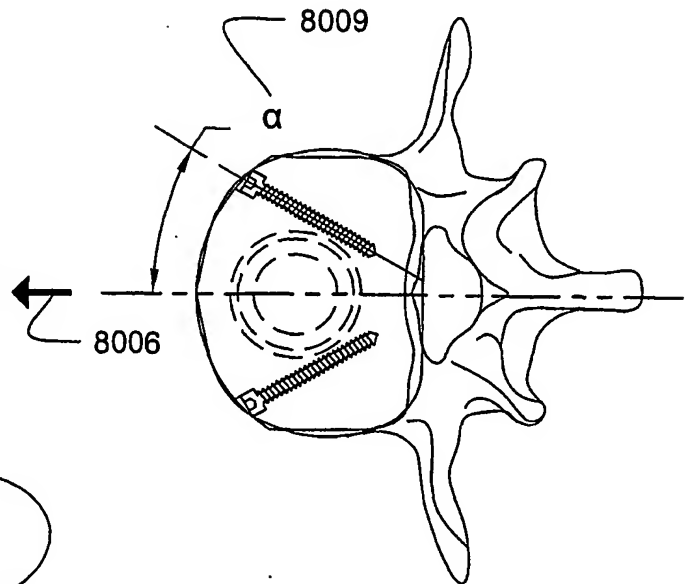
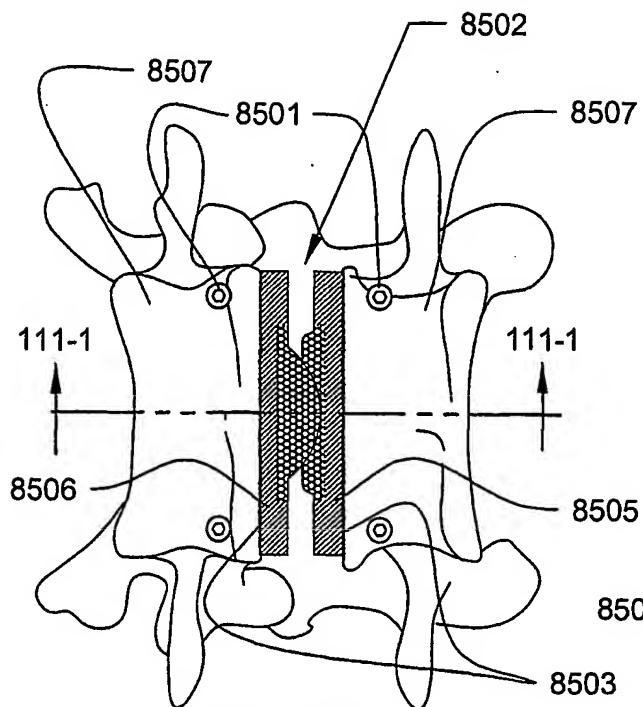
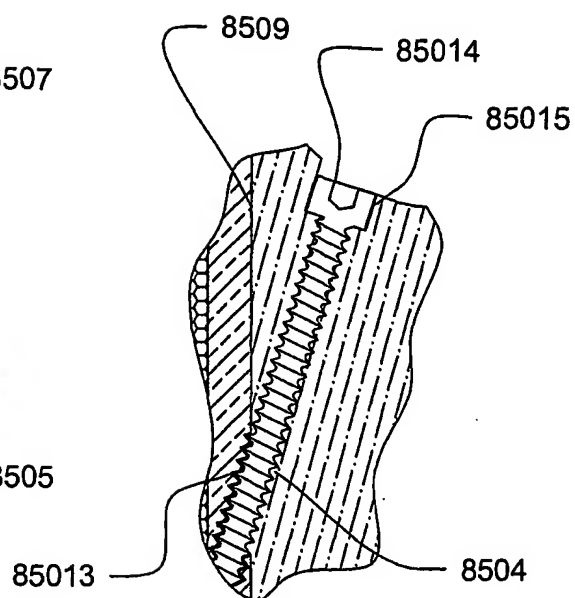


Fig. 110-2

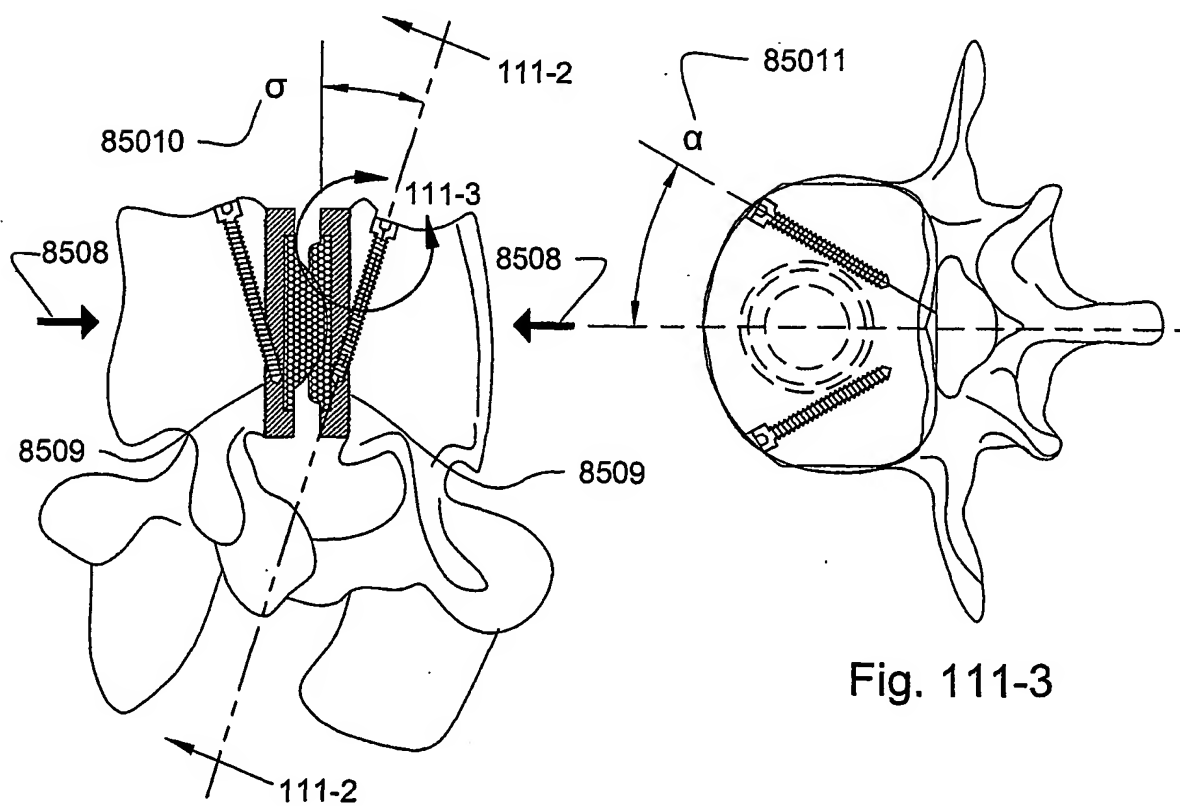




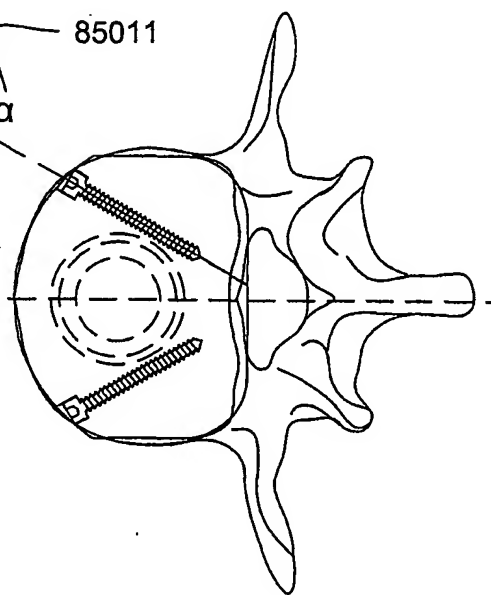
**Fig. 111**



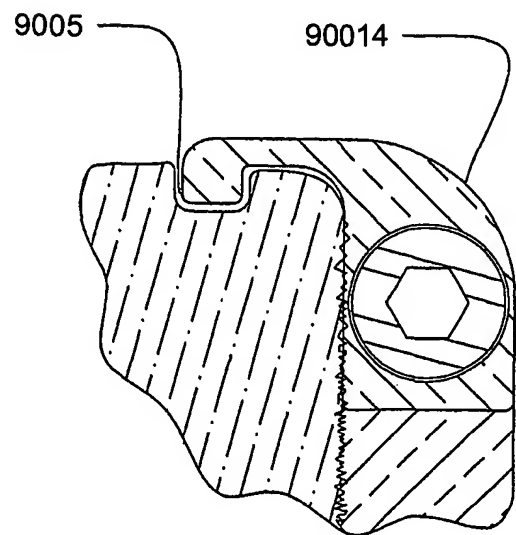
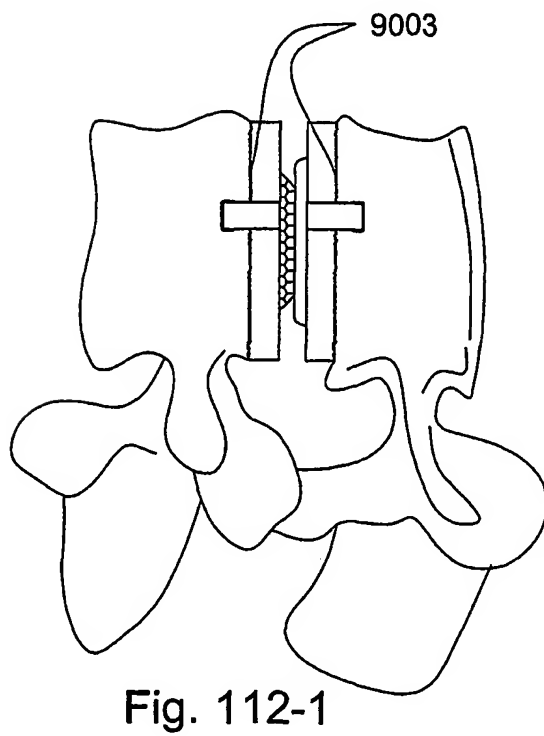
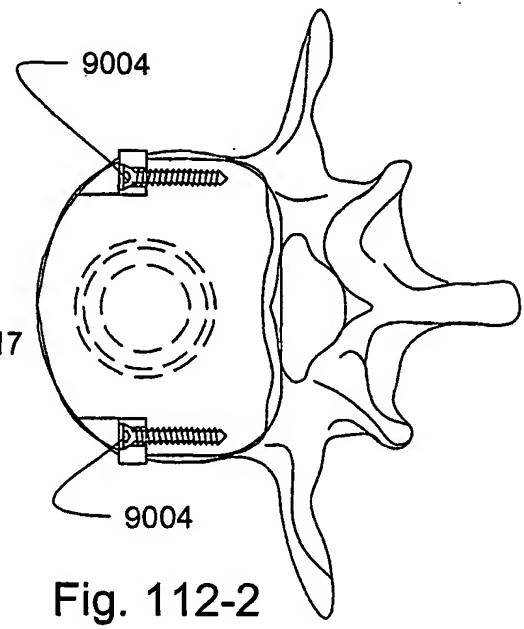
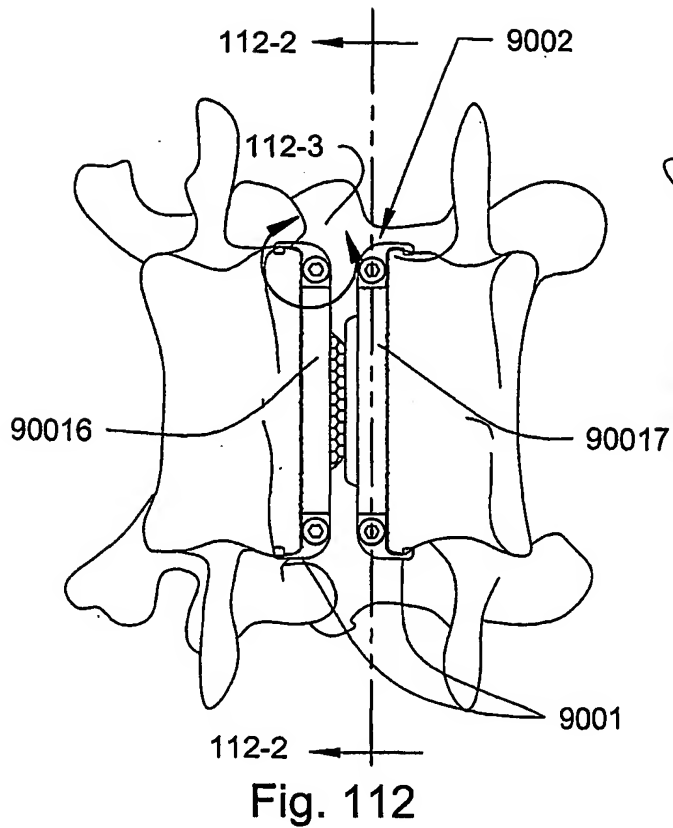
**Fig. 111-2**



**Fig. 111-1**



**Fig. 111-3**



# INTERNATIONAL SEARCH REPORT

International application No.

PCT/US03/27088

## A. CLASSIFICATION OF SUBJECT MATTER

IPC(7) : A61F 2/44

US CL : 623/17.14

According to International Patent Classification (IPC) or to both national classification and IPC

## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)

U.S. : 623/17.14,17.11,17.15

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practicable, search terms used)  
Please See Continuation Sheet

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	US 6,290,726 B1 (Pope et al) 18 September 2001, Fig. 2Z, col. 18, lines 47-67, col. 19, lines 1-3.	1-24
Y	US 6,179,874 B1 (Cauthen) 30 January 2001, see Figures, col. 5, lines 23-42, col. 6, lines 55-67.	1-24
Y	US 5,702,448 A (Buechel et al) 30 December 1997, col. 5, lines 14-16, 55-61, col. 7, lines 16-20.	1-24

☐ Further documents are listed in the continuation of Box C.

☐ See patent family annex.

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"E" earlier application or patent published on or after the international filing date

"L" document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified)

"O" document referring to an oral disclosure, use, exhibition or other means

"P" document published prior to the international filing date but later than the priority date claimed

"T"

later document published after the international filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention

"X"

document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone

"Y"

document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art

"&"

document member of the same patent family

Date of the actual completion of the international search

24 December 2003 (24.12.2003)

Date of mailing of the international search report

21 JAN 2004

Name and mailing address of the ISA/US

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Commissioner for Patents

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Facsimile No. (703) 305-3230

Authorized officer

Brian Pellegrino

Telephone No. 703-308-0858

**INTERNATIONAL SEARCH REPORT**

PCT/US03/27088

**Continuation of B. FIELDS SEARCHED Item 3:**

**EAST search terms:**

diamond, spinal, vertebral, articulating surfaces, convex, concave